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Published in the U.S.A.
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Chapter 1: Coupled-Field Analyses

A coupled-field analysis is a combination of analyses from different engineering disciplines (physics fields) that interact to solve a global engineering problem, hence, we often refer to a coupled-field analysis as a multiphysics analysis. When the input of one field analysis depends on the results from another analysis, the analyses are coupled.

Some analyses can have one-way coupling. For example, in a thermal stress problem, the temperature field introduces thermal strains in the structural field, but the structural strains generally do not affect the temperature distribution. Thus, there is no need to iterate between the two field solutions. More complicated cases involve two-way coupling. A piezoelectric analysis, for example, handles the interaction between the structural and electric fields: it solves for the voltage distribution due to applied displacements, or vice versa. In a fluid-structure interaction problem, the fluid pressure causes the structure to deform, which in turn causes the fluid solution to change. This problem requires iterations between the two physics fields for convergence.

The coupling between the fields can be accomplished by either direct coupling (matrix coupling) or sequential coupling (load vector coupling). Load transfer can take place across surfaces or volumes. Coupling across fields can be complicated because different fields may be solving for different types of analyses during a simulation. For example, in an induction heating problem, a harmonic electromagnetic analysis calculates Joule heating, which is used in a transient thermal analysis to predict a time-dependent temperature solution. The induction heating problem is complicated further by the fact that the material properties in both physics simulations depend highly on temperature.

Some of the applications in which coupled-field analysis may be required are pressure vessels (thermal-stress analysis), fluid flow constrictions (fluid-structure analysis), induction heating (magnetic-thermal analysis), ultrasonic transducers (piezoelectric analysis), magnetic forming (magneto-structural analysis), and micro-electromechanical systems (MEMS).

The following coupled-field analysis topics are available:
  1.1. Types of Coupled-Field Analysis
  1.2. System of Units
  1.3. About GUI Paths and Command Syntax

1.1. Types of Coupled-Field Analysis

The procedure for a coupled-field analysis depends on which fields are being coupled, but two distinct methods can be identified: sequential and direct. These methods are described briefly below, and in the following chapters in detail:

  • Chapter 2, “Sequentially Coupled Physics Analysis”
  • Chapter 3, “The ANSYS Multi-field (TM) Solver - MFS Single-Code Coupling”
  • Chapter 4, “Multi-field Analysis Using Code Coupling”
  • Chapter 5, “Unidirectional ANSYS to CFX Load Transfer”
  • Chapter 6, “Reduced Order Modeling”
  • Chapter 7, “Direct Coupled-Field Analysis”
  • Chapter 8, “Coupled Physics Circuit Simulation”
1.1.1. Sequential Method

The sequential method involves two or more sequential analyses, each belonging to a different field. There are different types of sequential analysis, explained in the following sections.

1.1.1.1. Sequentially Coupled Analysis - Physics Files

In a sequentially coupled physics analysis, you can couple the two fields by applying results from one analysis as loads in another analysis. The load transfer occurs external to the analysis, and you must explicitly transfer loads using the physics environment. An example of this type of analysis is a sequential thermal-stress analysis where nodal temperatures from the thermal analysis are applied as "body force" loads in the subsequent stress analysis. The physics analysis is based on a single finite element mesh across physics. Physics files can be used to perform coupled-field analysis. Physics files are created which prepare the single mesh for a given physics simulation. A solution proceeds in a sequential manner. A physics file is read to configure the database, a solution is performed, another physics field is read into the database, coupled-field loads are transferred, and the second physics is solved. Coupling occurs by issuing commands to read the coupled load terms from one physics to another across a node-node similar mesh interface.

1.1.1.2. Sequential Coupled Analysis - ANSYS Multi-field solver

The ANSYS Multi-field solver, available for a large class of coupled analysis problems. It is an automated tool for solving sequentially coupled field problems. It supersedes the physics file-based procedure and provides a robust, accurate, and easy to use tool for solving sequentially coupled physics problems. It is built on the premise that each physics is created as a field with an independent solid model and mesh. Surfaces or volumes are identified for coupled load transfer. A multi-field solver command set configures the problem and defines the solution sequencing. Coupled loads are automatically transferred across dissimilar meshes by the solver. The solver is applicable to static, harmonic, and transient analysis, depending on the physics requirements. Any number of fields may be solved in a sequential (or mixed sequential-simultaneous) manner.

Two versions of the ANSYS Multi-field solver, designed for different applications, offer their own benefits and different procedures:

- MFS - Single code: The basic ANSYS Multi-field solver used if the simulation involves small models with all physics field contained within a single product executable (e.g., ANSYS Multiphysics). The MFS - Single code solver uses iterative coupling where each physics is solved sequentially, and each matrix equation is solved separately. The solver iterates between each physics field until loads transferred across the physics interfaces converge.

- MFX - Multiple code: The enhanced ANSYS Multi-field solver used for simulations with physics fields distributed between more than one product executable (e.g., between ANSYS Multiphysics and ANSYS CFX). The MFX solver can accommodate much larger models than the MFS version. The MFX - Multiple code solver uses iterative coupling where each physics is solved either simultaneously or sequentially, and each matrix equation is solved separately. The solver iterates between each physics field until loads transferred across the physics interfaces converge.

1.1.1.3. Sequentially Coupled Analysis - Unidirectional ANSYS to CFX Load Transfer

The unidirectional ANSYS to CFX load transfer method is available for fluid-solid interaction problems where you know that the fluid analysis results do not affect the ANSYS loads significantly. Loads from an ANSYS Multiphysics analysis can then be unidirectionally transferred to a CFX fluid analysis.
1.1.2. Direct Method

The direct method usually involves just one analysis that uses a coupled-field element type containing all necessary degrees of freedom. Coupling is handled by calculating element matrices or element load vectors that contain all necessary terms. An example of this is a piezoelectric analysis using the PLANE223, SOLID226, or SOLID227 elements. Another example is MEMS analysis with the TRANS126 element.

1.1.3. When to Use Direct vs. Sequential

Direct coupling is advantageous when the coupled-field interaction is highly nonlinear and is best solved in a single solution using a coupled formulation. Examples of direct coupling include piezoelectric analysis, conjugate heat transfer with fluid flow, and circuit-electromagnetic analysis. Elements are specifically formulated to solve these coupled-field interactions directly.

For coupling situations which do not exhibit a high degree of nonlinear interaction, the sequential method is more efficient and flexible because you can perform the two analyses independently of each other. Coupling may be recursive where iterations between the different physics are performed until the desired level of convergence is achieved. In a sequential thermal-stress analysis, for example, you can perform a nonlinear transient thermal analysis followed by a linear static stress analysis. You can then use nodal temperatures from any load step or time-point in the thermal analysis as loads for the stress analysis. In a sequential coupling analysis, you can perform a nonlinear transient fluid-solid interaction analysis, using the FLOTRAN fluid elements and ANSYS structural, thermal or coupled field elements.

1.1.4. Miscellaneous Analysis Methods

In addition to the methods discussed above, ANSYS also offers additional methods:

1.1.4.1. Reduced Order Modeling

Reduced Order Modeling describes a solution method for efficiently solving coupled-field problems involving flexible structures. The reduced order modeling (ROM) method is based on a modal representation of the structural response. The deformed structural domain is described by a factored sum of the mode shapes (eigenvectors). The resulting ROM is essentially an analytical expression for the response of a system to any arbitrary excitation. This methodology has been implemented for coupled electrostatic-structural analysis and is applicable to micro-electromechanical systems (MEMS).

1.1.4.2. Coupled Physics Circuit Simulation

You can often perform coupled physics simulations using a circuit analogy. Components such as "lumped" resistors, sources, capacitors, and inductors can represent electrical devices. Equivalent inductances and resistances can represent magnetic devices, and springs, masses, and dampers can represent mechanical devices. ANSYS offers a set of tools to perform coupled simulations through circuits. A Circuit Builder is available to conveniently create circuit elements for electrical, magnetic, piezoelectric, and mechanical devices. The ANSYS circuit capability allows the user to combine both lumped elements where appropriate, with a "distributed" finite element model in regions where characterization requires a full finite element solution. A common degree-of-freedom set allows the combination of lumped and distributed models.

1.2. System of Units

In ANSYS, you must make sure that you use a consistent system of units for all the data you enter. You can use any consistent system of units. For electromagnetic field analysis, see the EMUNIT command in the ANSYS
Commands Reference for additional information regarding appropriate settings for free-space permeability and permittivity.

For micro-electromechanical systems (MEMS), it is best to set up problems in more convenient units since components may only be a few microns in size. For convenience, the following tables list the conversion factors from standard MKS units to µMKSV and µMSVfA units.

Table 1.1 Mechanical Conversion Factors for MKS to µMKSV

<table>
<thead>
<tr>
<th>Mechanical Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Length</td>
<td>m</td>
<td>m</td>
<td>10⁶</td>
<td>µm</td>
<td>µm</td>
</tr>
<tr>
<td>Force</td>
<td>N</td>
<td>(kg)(m)/(s)²</td>
<td>10⁶</td>
<td>µN</td>
<td>(kg)(µm)/(s)²</td>
</tr>
<tr>
<td>Time</td>
<td>s</td>
<td>s</td>
<td>1</td>
<td>s</td>
<td>s</td>
</tr>
<tr>
<td>Mass</td>
<td>kg</td>
<td>kg</td>
<td>1</td>
<td>kg</td>
<td>kg</td>
</tr>
<tr>
<td>Pressure</td>
<td>Pa</td>
<td>(kg)/(m)(s)²</td>
<td>10⁻⁶</td>
<td>MPa</td>
<td>(kg)/(µm)(s)²</td>
</tr>
<tr>
<td>Velocity</td>
<td>m/s</td>
<td>m/s</td>
<td>10⁶</td>
<td>µm/s</td>
<td>µm/s</td>
</tr>
<tr>
<td>Acceleration</td>
<td>m/(s)²</td>
<td>m/(s)²</td>
<td>10⁶</td>
<td>µm/(s)²</td>
<td>µm/(s)²</td>
</tr>
<tr>
<td>Density</td>
<td>kg/(m)³</td>
<td>kg/(m)³</td>
<td>10⁻¹⁸</td>
<td>kg/(µm)³</td>
<td>kg/(µm)³</td>
</tr>
<tr>
<td>Stress</td>
<td>Pa</td>
<td>kg/(m)(s)²</td>
<td>10⁻⁶</td>
<td>MPa</td>
<td>kg/(µm)(s)²</td>
</tr>
<tr>
<td>Young’s Modulus</td>
<td>Pa</td>
<td>kg/(m)(s)²</td>
<td>10⁻⁶</td>
<td>MPa</td>
<td>kg/(µm)(s)²</td>
</tr>
<tr>
<td>Power</td>
<td>W</td>
<td>(kg)(m)²/(s)³</td>
<td>10⁻¹²</td>
<td>pW</td>
<td>(kg)(µm)²/(s)³</td>
</tr>
</tbody>
</table>

Table 1.2 Thermal Conversion Factors for MKS to µMKSV

<table>
<thead>
<tr>
<th>Thermal Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Conductivity</td>
<td>W/(m)(K)</td>
<td>(kg)/(m)/(K)(s)³</td>
<td>10⁶</td>
<td>pW/(µm)(K)</td>
<td>(kg)/(µm)(K)(s)³</td>
</tr>
<tr>
<td>Heat Flux</td>
<td>W/(m)²</td>
<td>kg/(s)³</td>
<td>1</td>
<td>pW/(µm)²</td>
<td>kg/(s)³</td>
</tr>
<tr>
<td>Specific Heat</td>
<td>J/(kg)(K)</td>
<td>(m)²/(K)(s)²</td>
<td>10¹²</td>
<td>pJ/(kg)(K)</td>
<td>(m)²/(K)(s)²</td>
</tr>
<tr>
<td>Heat Flow</td>
<td>W</td>
<td>(kg)(m)²/(s)³</td>
<td>10¹²</td>
<td>pW</td>
<td>(kg)(µm)²/(s)³</td>
</tr>
<tr>
<td>Heat Generation Per Volume</td>
<td>W/m³</td>
<td>(kg)/(m)(s)³</td>
<td>10⁻⁶</td>
<td>pW/(µm)³</td>
<td>kg/(µm)(s)³</td>
</tr>
<tr>
<td>Convection Coefficient</td>
<td>W/(m)²(K)</td>
<td>kg/(s)³(K)</td>
<td>1</td>
<td>pW/(µm)²(K)</td>
<td>kg/(s)³(K)</td>
</tr>
<tr>
<td>Dynamic Viscosity</td>
<td>kg/(m)(s)</td>
<td>kg/(m)(s)</td>
<td>10⁻⁶</td>
<td>kg/(µm)(s)</td>
<td>kg/(µm)(s)</td>
</tr>
<tr>
<td>Kinematic Viscosity</td>
<td>(m)²/s</td>
<td>(m)²/s</td>
<td>10¹²</td>
<td>(µm)²/s</td>
<td>(µm)²/s</td>
</tr>
</tbody>
</table>

Table 1.3 Electrical Conversion Factors for MKS to µMKSV

<table>
<thead>
<tr>
<th>Electrical Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Current</td>
<td>A</td>
<td>A</td>
<td>10¹²</td>
<td>pA</td>
<td>pA</td>
</tr>
<tr>
<td>Voltage</td>
<td>V</td>
<td>(kg)(m)²/(A)(s)³</td>
<td>1</td>
<td>V</td>
<td>(kg)(µm)²/(pA)(s)³</td>
</tr>
</tbody>
</table>
Table 1.4 Magnetic Conversion Factors for MKS to µMKSV

<table>
<thead>
<tr>
<th>Magnetic Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Flux</td>
<td>Weber</td>
<td>(kg)(m)^2/(A)(s)^2</td>
<td>1</td>
<td>Weber</td>
<td>(kg)(µm)^2/(pA)(s)^2</td>
</tr>
<tr>
<td>Flux Density</td>
<td>Tesla</td>
<td>kg/(A)(s)^2</td>
<td>10^{-12}</td>
<td>Tesla</td>
<td>kg/(pA)(s)^2</td>
</tr>
<tr>
<td>Field Intensity</td>
<td>A/m</td>
<td>A/m</td>
<td>10^6</td>
<td>pA/µm</td>
<td>pA/µm</td>
</tr>
<tr>
<td>Current</td>
<td>A</td>
<td>A</td>
<td>10^{-12}</td>
<td>pA</td>
<td>pA</td>
</tr>
<tr>
<td>Current Density</td>
<td>A/(m)^2</td>
<td>A/(m)^2</td>
<td>1</td>
<td>pA/(µm)^2</td>
<td>pA/(µm)^2</td>
</tr>
<tr>
<td>Permeability [1]</td>
<td>H/m</td>
<td>(kg)(m)/(A)^2(s)^2</td>
<td>10^{-18}</td>
<td>TH/µm</td>
<td>(kg)(µm)/(pA)^2(s)^2</td>
</tr>
<tr>
<td>Inductance</td>
<td>H</td>
<td>(kg)(m)^2/(A)^2(s)^2</td>
<td>10^{-12}</td>
<td>TH</td>
<td>(kg)(µm)^2/(pA)^2(s)^2</td>
</tr>
</tbody>
</table>

1. Free-space permeability is equal to 4π x 10^{-25} TH/µm.

Note — Only constant permeability may be used with these units.

Table 1.5 Piezoelectric Conversion Factors for MKS to µMKSV

<table>
<thead>
<tr>
<th>Piezoelectric Matrix [1]</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Stress Matrix [e]</td>
<td>C/(m)^2</td>
<td>(A)/(m)^2</td>
<td>1</td>
<td>pC/(µm)^2</td>
<td>(pA)/(µm)^2</td>
</tr>
<tr>
<td>Strain Matrix [d]</td>
<td>C/N</td>
<td>(A)/(µm)^2/(kg)(m)</td>
<td>10^6</td>
<td>pC/(µN)</td>
<td>(pA)/(µm)^2/(kg)(µm)</td>
</tr>
</tbody>
</table>

1. For information on piezoelectric matrices, see Section 7.3: Piezoelectric Analysis.

Table 1.6 Piezoresistive Conversion Factors for MKS to µMKSV

<table>
<thead>
<tr>
<th>Piezoresistive Matrix [1]</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Piezoresistive Stress Matrix [π]</td>
<td>Pa^{-1}</td>
<td>(m)(s)^5/kg</td>
<td>10^6</td>
<td>(MPa)^{-1}</td>
<td>(µm)(s)^5/kg</td>
</tr>
</tbody>
</table>

1. Free-space permittivity is equal to 8.854 x 10^{-6} pF/µm.
1. For information on piezoresistive matrices, see Section 2.5.8: Piezoresistive Materials in the ANSYS Elements Reference.

**Table 1.7 Thermoelectric Conversion Factors for MKS to \( \mu \text{MKSV} \)**

<table>
<thead>
<tr>
<th>Thermoelectric Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain ( \mu \text{MKSV} ) Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Seebeck Coefficient</td>
<td>V/K</td>
<td>((\text{kg})(\text{m})^2/(\text{A})(s)^3)(K)</td>
<td>1</td>
<td>V/K</td>
<td>((\text{kg})(\mu\text{m})^2/(\mu\text{A})(s)^3)(K)</td>
</tr>
</tbody>
</table>

**Table 1.8 Mechanical Conversion Factors for MKS to \( \mu \text{MSVfa} \)**

<table>
<thead>
<tr>
<th>Mechanical Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain ( \mu \text{MSVfa} ) Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Length</td>
<td>m</td>
<td>m</td>
<td>10^6</td>
<td>(\mu\text{m} )</td>
<td>(\mu \text{m} )</td>
</tr>
<tr>
<td>Force</td>
<td>N</td>
<td>((\text{kg})(\text{m})/(\text{s})^2)</td>
<td>10^9</td>
<td>nN</td>
<td>(g)(\mu\text{m})/(s)^2</td>
</tr>
<tr>
<td>Time</td>
<td>s</td>
<td>s</td>
<td>1</td>
<td>s</td>
<td>s</td>
</tr>
<tr>
<td>Mass</td>
<td>kg</td>
<td>kg</td>
<td>10^3</td>
<td>g</td>
<td>g</td>
</tr>
<tr>
<td>Pressure</td>
<td>Pa</td>
<td>((\text{kg})/(\text{m})(\text{s})^2)</td>
<td>10^3</td>
<td>kPa</td>
<td>g/(\mu\text{m})(s)^2</td>
</tr>
<tr>
<td>Velocity</td>
<td>m/s</td>
<td>m/s</td>
<td>10^6</td>
<td>(\mu\text{m/s} )</td>
<td>(\mu\text{m/s} )</td>
</tr>
<tr>
<td>Acceleration</td>
<td>m/(s)^2</td>
<td>m/(s)^2</td>
<td>10^6</td>
<td>(\mu\text{m/s} )</td>
<td>(\mu\text{m/s} )</td>
</tr>
<tr>
<td>Density</td>
<td>kg/(m)^3</td>
<td>kg/(m)^3</td>
<td>10^-15</td>
<td>g/(\mu\text{m})^3</td>
<td>g/(\mu\text{m})^3</td>
</tr>
<tr>
<td>Stress</td>
<td>Pa</td>
<td>kg/(m)(s)^2</td>
<td>10^3</td>
<td>kPa</td>
<td>g/(\mu\text{m})(s)^2</td>
</tr>
<tr>
<td>Young's Modulus</td>
<td>Pa</td>
<td>kg/(m)(s)^2</td>
<td>10^3</td>
<td>kPa</td>
<td>g/(\mu\text{m})(s)^2</td>
</tr>
<tr>
<td>Power</td>
<td>W</td>
<td>((\text{kg})(\text{m})^2/(\text{s})^3)</td>
<td>10^15</td>
<td>fW</td>
<td>(g)(\mu\text{m})^2/(s)^3</td>
</tr>
</tbody>
</table>

**Table 1.9 Thermal Conversion Factors for MKS to \( \mu \text{MSVfa} \)**

<table>
<thead>
<tr>
<th>Thermal Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain ( \mu \text{MSVfa} ) Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Conductivity</td>
<td>W/(m)(K)</td>
<td>((\text{kg})(\text{m})(\text{K})/(\text{s})^3)</td>
<td>10^9</td>
<td>fW/(\mu\text{m})(K)</td>
<td>(g)(\mu\text{m})(\text{K})(s)^3</td>
</tr>
<tr>
<td>Heat Flux</td>
<td>W/(m)^2</td>
<td>(\text{kg}/(\text{s})^3)</td>
<td>10^3</td>
<td>fW/(\mu\text{m})^2</td>
<td>g/(s)^3</td>
</tr>
<tr>
<td>Specific Heat</td>
<td>J/(kg)(K)</td>
<td>((\text{m})^2/(\text{K})(\text{s})^2)</td>
<td>10^12</td>
<td>fJ/(g)(K)</td>
<td>(\mu\text{m})^2/(K)(s)^2</td>
</tr>
<tr>
<td>Heat Flow</td>
<td>W</td>
<td>((\text{kg})(\text{m})^2/(\text{s})^3)</td>
<td>10^15</td>
<td>fW</td>
<td>(g)(\mu\text{m})^2/(s)^3</td>
</tr>
<tr>
<td>Heat Generation Per Volume</td>
<td>W/m^3</td>
<td>((\text{kg})(\text{m})(\text{s})^3)</td>
<td>10^3</td>
<td>fW/(\mu\text{m})^3</td>
<td>g/(\mu\text{m})(s)^3</td>
</tr>
<tr>
<td>Convection Coefficient</td>
<td>W/(m)^2(K)</td>
<td>(\text{kg}/(\text{s})^3)(K)</td>
<td>10^3</td>
<td>fW/(\mu\text{m})^2(K)</td>
<td>g/(s)^3(K)</td>
</tr>
<tr>
<td>Dynamic Viscosity</td>
<td>kg/(m)(s)</td>
<td>kg/(m)(s)</td>
<td>10^3</td>
<td>g/(\mu\text{m})(s)</td>
<td>g/(\mu\text{m})(s)</td>
</tr>
<tr>
<td>Kinematic Viscosity</td>
<td>((\text{m})^2/\text{s})</td>
<td>((\text{m})^2/\text{s})</td>
<td>10^12</td>
<td>(\mu\text{m})^2/s</td>
<td>(\mu\text{m})^2/s</td>
</tr>
</tbody>
</table>
### Table 1.10 Electrical Conversion Factors for MKS to µMSVfA

<table>
<thead>
<tr>
<th>Electrical Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMsvfa Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Current</td>
<td>A</td>
<td>A</td>
<td>$10^{15}$</td>
<td>fA</td>
<td>fA</td>
</tr>
<tr>
<td>Voltage</td>
<td>V</td>
<td>(kg)(m)/((A)(s))$^3$</td>
<td>1</td>
<td>V</td>
<td>(g)(µm)$^2$/(fA)(s)$^3$</td>
</tr>
<tr>
<td>Charge</td>
<td>C</td>
<td>(A)(s)</td>
<td>$10^{15}$</td>
<td>fC</td>
<td>(fA)(s)</td>
</tr>
<tr>
<td>Conductivity</td>
<td>S/m</td>
<td>(A)$^2$/(kg)(m)$^3$</td>
<td>$10^9$</td>
<td>nS/µm</td>
<td>(fA)$^2$/(g)(µm)$^3$</td>
</tr>
<tr>
<td>Resistivity</td>
<td>Ωm</td>
<td>(kg)(m)$^3$/(A)$^2$</td>
<td>$10^9$</td>
<td>-</td>
<td>(g)(µm)$^2$/(fA)$^2$</td>
</tr>
<tr>
<td>Permittivity [1]</td>
<td>F/m</td>
<td>(A)$^2$/(kg)(m)$^3$</td>
<td>$10^9$</td>
<td>fF/µm</td>
<td>(fA)$^2$/(g)(µm)$^3$</td>
</tr>
<tr>
<td>Energy</td>
<td>J</td>
<td>(kg)(m)/s$^2$</td>
<td>$10^{15}$</td>
<td>fJ</td>
<td>(g)(µm)$^2$/(s)$^2$</td>
</tr>
<tr>
<td>Capacitance</td>
<td>F</td>
<td>(A)$^2$/(kg)(m)$^2$</td>
<td>$10^{15}$</td>
<td>fF</td>
<td>(fA)$^2$/(g)(µm)$^3$</td>
</tr>
<tr>
<td>Electric Field</td>
<td>V/m</td>
<td>(kg)(m)/s$^2$(A)</td>
<td>$10^9$</td>
<td>V/µm</td>
<td>(g)(µm)/s(fA)</td>
</tr>
<tr>
<td>Electric Flux Density</td>
<td>C/(m)$^2$</td>
<td>(A)/(s)/(m)$^2$</td>
<td>$10^3$</td>
<td>fC/(µm)$^2$</td>
<td>(fA)/(s)/(µm)$^2$</td>
</tr>
</tbody>
</table>

1. Free-space permittivity is equal to $8.854 \times 10^{-3}$ fF/µm.

### Table 1.11 Magnetic Conversion Factors for MKS to µMKSVfA

<table>
<thead>
<tr>
<th>Magnetic Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Flux</td>
<td>Weber</td>
<td>(kg)(m)/((A)(s))$^2$</td>
<td>1</td>
<td>Weber</td>
<td>(g)(µm)$^2$/(fA)(s)$^2$</td>
</tr>
<tr>
<td>Flux Density</td>
<td>Tesla</td>
<td>kg/(A)(s)$^2$</td>
<td>$10^{-12}$</td>
<td>-</td>
<td>g/(fA)(s)$^2$</td>
</tr>
<tr>
<td>Field Intensity</td>
<td>A/m</td>
<td>A/m</td>
<td>$10^9$</td>
<td>fA/µm</td>
<td>fA/µm</td>
</tr>
<tr>
<td>Current</td>
<td>A</td>
<td>A</td>
<td>$10^{15}$</td>
<td>fA</td>
<td>fA</td>
</tr>
<tr>
<td>Current Density</td>
<td>A/(m)$^2$</td>
<td>A/(m)$^2$</td>
<td>$10^3$</td>
<td>fA/(µm)$^2$</td>
<td>fA/(µm)$^2$</td>
</tr>
<tr>
<td>Permeability [1]</td>
<td>H/m</td>
<td>(kg)(m)/(A)$^2$</td>
<td>$10^{21}$</td>
<td>-</td>
<td>(g)(µm)/(fA)$^2$</td>
</tr>
<tr>
<td>Inductance</td>
<td>H</td>
<td>(kg)(m)/(A)$^2$</td>
<td>$10^{-15}$</td>
<td>-</td>
<td>(g)(µm)$^2$/(fA)$^2$</td>
</tr>
</tbody>
</table>

1. Free-space permeability is equal to $4 \pi \times 10^{-28}$ (g)(µm)/(fA)$^2$.

*Note* — Only constant permeability may be used with these units.

### Table 1.12 Piezoelectric Conversion Factors for MKS to µMKSVfA

<table>
<thead>
<tr>
<th>Piezoelectric Matrix [1]</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Piezoelectric Stress [e]</td>
<td>C/(m)$^2$</td>
<td>(A)/(s)/(m)$^2$</td>
<td>$10^3$</td>
<td>fC/(µm)$^2$</td>
<td>(fA)/(s)/(µm)$^2$</td>
</tr>
<tr>
<td>Piezoelectric Strain [d]</td>
<td>C/N</td>
<td>(A)/(s)$^3$/(kg)(m)</td>
<td>$10^6$</td>
<td>fC/(µN)</td>
<td>(fA)/(s)$^3$/(g)(µm)</td>
</tr>
</tbody>
</table>

1. For information on piezoelectric matrices, see Section 7.3: Piezoelectric Analysis.
Table 1.13 Piezoresistive Conversion Factors for MKS to µMKSVfA

<table>
<thead>
<tr>
<th>Piezoresistive Matrix [1]</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Piezoresistive Stress Matrix [π]</td>
<td>Pa⁻¹</td>
<td>(m)(s)²/kg</td>
<td>10³</td>
<td>(kPa)⁻¹</td>
<td>(µm)(s)²/g</td>
</tr>
</tbody>
</table>

1. For information on piezoresistive matrices, see Section 2.5.8: Piezoresistive Materials in the ANSYS Elements Reference.

Table 1.14 Thermoelectric Conversion Factors for MKS to µMKSVfA

<table>
<thead>
<tr>
<th>Thermoelectric Parameter</th>
<th>MKS Unit</th>
<th>Dimension</th>
<th>Multiply by This Number</th>
<th>To Obtain µMKSV Unit</th>
<th>Dimension</th>
</tr>
</thead>
<tbody>
<tr>
<td>Seebeck Coefficient</td>
<td>V/K</td>
<td>(kg)(m)²/(A)(s)³(K)</td>
<td>1</td>
<td>V/K</td>
<td>(g)(µm)²/(fA)(s)³(K)</td>
</tr>
</tbody>
</table>

1.3. About GUI Paths and Command Syntax

Throughout this document, you will see references to ANSYS commands and their equivalent GUI paths. Such references use only the command name because you do not always need to specify all of a command’s arguments, and specific combinations of command arguments perform different functions. For complete syntax descriptions of ANSYS commands, consult the ANSYS Commands Reference.

The GUI paths shown are as complete as possible. In many cases, choosing the GUI path as shown will perform the function you want. In other cases, choosing the GUI path given in this document takes you to a menu or dialog box; from there, you must choose additional options that are appropriate for the specific task being performed.

For all types of analyses described in this guide, specify the material you will be simulating using an intuitive material model interface. This interface uses a hierarchical tree structure of material categories, which is intended to assist you in choosing the appropriate model for your analysis. See Section 1.1.4.4: Material Model Interface in the ANSYS Basic Analysis Guide for details on the material model interface.
Chapter 2: Sequentially Coupled Physics Analysis

A sequentially coupled physics analysis is the combination of analyses from different engineering disciplines which interact to solve a global engineering problem. For convenience, this chapter refers to the solutions and procedures associated with a particular engineering discipline as a *physics analysis*. When the input of one physics analysis depends on the results from another analysis, the analyses are coupled.

Some cases use only one-way coupling. For example, the calculation of the flow field over a cement wall provides pressure loads which you can use in the structural analysis of the wall. The pressure loadings result in a deflection of the wall. This in principle changes the geometry of the flow field around the wall, but in practice, the change is small enough to be negligible. Thus, there is no need to iterate. Of course, in this problem fluid elements are used for the flow solution and structural elements, for the stress and deflection calculations.

A more complicated case is the induction heating problem, where an AC electromagnetic analysis calculates Joule heat generation data which a transient thermal analysis uses to predict a time-dependent temperature solution. The induction heating problem is complicated further by the fact that the material properties in both physics simulations depend highly on temperature. This requires iteration between the two simulations.

The term *sequentially coupled physics* refers to solving one physics simulation after another. Results from one analysis become loads for the next analysis. If the analyses are fully coupled, results of the second analysis will change some input to the first analysis. The complete set of boundary conditions and loads consists of the following:

- *Base physics loads*, which are not a function of other physics analyses. Such loads also are called *nominal boundary conditions*.
- *Coupled loads*, which are results of the other physics simulation.

Typical applications you can solve with ANSYS include the following:

- Thermal stress
- Induction heating
- Induction stirring
- Steady-state fluid-structure interaction
- Magnetostatic interaction
- Electrostatic-structural interaction
- Current conduction-magnetostatics

The ANSYS program can perform multiphysics analyses with a single ANSYS database. A single set of nodes and elements will exist for the entire model. What these elements represent are changes from one physics analysis to another, based on the use of the physics environment concept.

The following sequentially-coupled analysis topics are available:

2.1. What Is a Physics Environment?
2.2. General Analysis Procedures
2.3. Transferring Loads Between Physics
2.4. Performing a Sequentially Coupled Physics Analysis with Physics Environments
2.5. Example Thermal-Stress Analysis Using the Indirect Method
2.1. What Is a Physics Environment?

The ANSYS program performs sequentially coupled physics analyses using the concept of a physics environment. The term physics environment applies to both a file you create which contains all operating parameters and characteristics for a particular physics analysis and to the file's contents. A physics environment file is an ASCII file you create using either of the following:

Command(s): PHYSICS, WRITE, Title, Filename, Ext, --
GUI: Main Menu> Preprocessor> Physics> Environment
Main Menu> Solution> Physics> Environment

You can define up to nine physics environments for a particular jobname. You define a unique title for each environment on the PHYSICS command. ANSYS gives each physics environment a unique number as part of its file extension. Using a title that describes the physics of the analysis is recommended. The title also needs to be different from the analysis title specified with the /TITLE command (Utility Menu> File> Change Title).

The PHYSICS, WRITE command creates a physics environment file (Jobname.PH1, for example) by taking the following information from the ANSYS database:

- Element types and KEYOPT settings
- Real constants
- Material properties
- Element coordinate systems
- Solution analysis options
- Load step options
- Constraint equations
- Coupled node sets
- Applied boundary conditions and loads
- GUI Preference settings
- The analysis title (/TITLE card)

You use either the PHYSICS, READ command (Main Menu> Preprocessor> Physics> Environment> Read) to read in a physics environment file, using either the filename or the title used in writing the file. (This title is included as a comment at the top of the physics environment file.) Before reading the physics file, the ANSYS program clears all boundary conditions, loads, node coupling, material properties, analysis options, and constraint equations that presently exist in the database.

2.2. General Analysis Procedures

You can perform a sequential coupled-field analysis using either an indirect method or the physics environments.

In the indirect method, you maintain different databases and results files. Figure 2.1: “Data Flow for a Sequential Coupled-Field Analysis” shows the data flow for a typical sequential analysis done with the indirect method. Each data base contains the appropriate solid model, elements, loads, etc. You can read information from a results file into another database. Element and node numbers must be consistent between the databases and the results file.
Figure 2.1 Data Flow for a Sequential Coupled-Field Analysis

Figure 2.2: “Data Flow for a Sequentially Coupled Physics Analysis (Using Physics Environments)” shows the data flow using the physics environment approach. In this approach, a single database exists for the entire model. The database must contain the elements and nodes for all the physics analyses which you undertake. For each element or solid model entity, you must define a set of attribute numbers. These include an element type number, a material number, a real constant number, and an element coordinate system number. All of these numbers will remain constant across all the analyses. However, the actual properties associated with a given attribute number can vary among all the physics environments, as can the definition of the parameters in real constant sets and the element type number. Regions of the model may be inactive for a particular physics solution, as this chapter will explain later.
You should build the ANSYS database with the requirements of each physics environment in mind. Before creating any physics environments, assign the element type number, material number, real constant set number, and element coordinate set number of each distinct region for each area or volume. (See the descriptions of the AATT and VATT commands.) Be careful when working with problems where a given area or volume is part of the problem domain for two different physics types. For example, a fluid may have magnetic characteristics. Any region that will be a fluid region at any time must have a material number of 1. If you cannot do this, you will have to modify the appropriate elements between performing the different physics solutions. To modify elements, use one of the following:

**Command(s):** EMODIF  
**GUI:** Main Menu> Preprocessor> Modeling> Move/Modify> Elements> Modify Attrib

The indirect method is ideal for one-way sequential coupling, such as a typical thermal-stress analysis. The physics environment approach allows for quick switching between physics environments, which is ideally suited for fully coupled scenarios requiring multiple passes between physics solutions. Large-deflection steady-state fluid-structure interaction, or induction heating, are typical examples of cases requiring the physics environment approach.
Note that the database file may grow in size during multiple solution passes unless you take one of the following actions:

- Issue a `SAVE` after creating the physics environments and a `RESUME` after each physics solution.
- Do not write results into the database (only write to the results file). You will then need to issue a `SET` command whenever you want to read data from the results file into the database for postprocessing. To invoke this option, either issue the command `/CONFIG,NOELAB,1` or insert the line "NO_ELDBW = 1" into the `config100.ans` file.

### 2.3. Transferring Loads Between Physics

The `LDREAD` command links the different physics environments in a coupled-field analysis, enabling you to read in specified results data from the first physics environment solution analysis and applying them as loads for the next environment\textquotesingle s solution.

The `LDREAD` command reads results data from the results file and applies them as loads. The following table briefly explains what happens to results data from various analysis types when `LDREAD` reads them in as loads on another analysis:

#### Table 2.1 How Results Transferred by LDREAD Become Loads

<table>
<thead>
<tr>
<th>These analysis results ...</th>
<th>Become loads on this type of analysis ...</th>
</tr>
</thead>
<tbody>
<tr>
<td>Temperatures from a thermal or FLOTRAN analysis [TEMP, TBOT, TE2, … TTOP]</td>
<td>Body force for structural analyses or nodal loads (temperatures) for thermal analyses</td>
</tr>
<tr>
<td>Forces from a static, harmonic, or transient magnetic analysis [FORC]</td>
<td>Force loads on a structural analysis or FLOTRAN analysis</td>
</tr>
<tr>
<td>Forces from an electrostatic analysis [FORC]</td>
<td>Force loads on a structural analysis</td>
</tr>
<tr>
<td>Joule heating from a magnetic analysis [HGEN]</td>
<td>Body force element (heat generation) loads onto a thermal or FLOTRAN analysis</td>
</tr>
<tr>
<td>Source current density from a current conduction analysis [JS]</td>
<td>Body force element (current density) loads on a magnetic field analysis</td>
</tr>
<tr>
<td>Pressures from a FLOTRAN analysis [PRES]</td>
<td>Surface (pressure) loads onto a structural analysis (solids and shell elements)</td>
</tr>
<tr>
<td>Reaction loads from any analysis [REAC]</td>
<td>Force loads on any analysis</td>
</tr>
<tr>
<td>Heat fluxes from a FLOTRAN analysis [HFLU]</td>
<td>Surface (heat flux) loads on elements in a thermal analysis</td>
</tr>
<tr>
<td>Heat fluxes from a high frequency electromagnetic analysis [EHFLU]</td>
<td>Surface (heat flux) loads on elements in a thermal analysis</td>
</tr>
<tr>
<td>FLOTRAN calculated film coefficient and associated ambient temperature [HFLM]</td>
<td>Surface (film coefficients and bulk temperature) loads on elements in a thermal analysis</td>
</tr>
</tbody>
</table>

#### 2.3.1. Compatible Element Types

There are several criteria for determining if element types are compatible across physics environments. Before reading further about this topic, you need to understand the following terms:

**Base geometry**

An element\textquotesingle s base geometry is established by the default configuration documented in the *ANSYS Elements Reference*. For solid elements, base geometry includes quadrilateral, triangle, hexahedron (brick), and tetrahedron shapes.
Degenerate geometry

Many elements may take on a degenerate form from the base geometry. For instance, a quadrilateral element may degenerate to a triangle element, or a brick element may degenerate to a wedge, tetrahedron, or pyramid shape.

Element order

ANSYS elements (excluding the p-elements) are available in a "lower" order form (first order) or a "higher" order form (second order). The higher order elements have midside nodes; the lower order elements do not. In many instances, you can generate the higher order elements without midside nodes.

Across multiphysics environments, element types must maintain a consistent base geometry. If an element type allows a degenerate geometry, the corresponding element type in the other physics must also allow the same degenerate geometry. For example, a SOLID92 (10-node tetrahedral structural solid) is compatible with SOLID87 (a 10-node tetrahedral thermal solid). However, SOLID92 is not compatible with a degenerate tetrahedral shape of SOLID90 (a 20-node thermal solid).

Elements of different element order may or may not be compatible across physics environments. The nature of the coupled load read by the LDREAD command will determine compatibility. In addition, certain element types have specific KEYOPT options that support lower and higher order coupled load transfer.

The items listed below are loads which you can read from first or second order elements and apply to first or second order elements in another physics environment:

- Body force temperatures [TEMP, TBOT, TE2, . . . TTOP]
- Body force element heat generation [HGEN]
- Source current density [JS]
- Surface pressure [PRES]
- Surface heat fluxes [HFLU]
- Surface film coefficients and bulk temperature [HFLM]

Loads which require compatibility in element order are as follows:

- Force loads* [FORC]
- Reaction loads [REAC]

*The following electromagnetic elements support first or second order structural elements with a KEYOPT setting: PLANE53, PLANE121, SOLID122, and SOLID123.

If physics environments are established by switching between element orders, you must initially create the finite element mesh with the higher order elements. Table 2.2: "Compatible Element Types Across Physics Environments" partially summarizes compatible element types:

<table>
<thead>
<tr>
<th>Structural</th>
<th>Thermal</th>
<th>Magnetic</th>
<th>Electrostatic</th>
<th>Fluid</th>
<th>Electric Conduction</th>
</tr>
</thead>
<tbody>
<tr>
<td>SOLID95</td>
<td>SOLID90</td>
<td>SOLID117, HF120</td>
<td>SOLID122</td>
<td>-</td>
<td>SOLID5, SOLID69</td>
</tr>
<tr>
<td>PLANE2</td>
<td>PLANE35</td>
<td>-</td>
<td>-</td>
<td>-</td>
<td>-</td>
</tr>
</tbody>
</table>

Table 2.2 Compatible Element Types Across Physics Environments
Note — If a mesh involves a degenerate element shape, the corresponding element type must allow the same degenerate shape. For example, if a mesh involves FLUID142 pyramid elements, SOLID70 elements are not compatible. SOLID70 elements cannot be degenerated into a pyramid shape. To be compatible, elements with a VOLT degree of freedom must also have the same reaction force (see Element Compatibility in the *ANSYS Low-Frequency Electromagnetic Analysis Guide*).

1. Supports only first order elements requiring forces.
2. Element KEYOPT option required to support first order elements requiring forces.

### 2.3.2. Types of Results Files You May Use

In an indirect coupled-field analysis or a physics environment analysis, typically you work with several different types of results files containing different types. All results files for your analysis will have the same filename (the jobname you specified using either the `/FILNAME` command ([Utility Menu> File> Change Jobname](https://www.ansys.com/))). However, you can distinguish among different results files by looking at their extensions:

<table>
<thead>
<tr>
<th>Jobname.RFL</th>
<th>FLOTRAN results file</th>
</tr>
</thead>
<tbody>
<tr>
<td>Jobname.RMG</td>
<td>Electromagnetic results file</td>
</tr>
<tr>
<td>Jobname.RTH</td>
<td>Thermal results file</td>
</tr>
<tr>
<td>Jobname.RST</td>
<td>All other types of results files (structural and multiple physics)</td>
</tr>
</tbody>
</table>

### 2.3.3. Transient Fluid-Structural Analyses

In a transient fluid-structural analyses, you may choose to perform structural analyses at intermediate times corresponding to ramped changes in fluid boundary conditions. For example, suppose you want to perform a structural analysis at 2.0 seconds and the inlet velocity ramps from 1.0 in/sec at 0.0 seconds to 5.0 in/sec at 4.0 seconds. You first perform the structural analysis at 2.0 seconds in the usual manner. When the PHYSICS,READ,FLUID ([Main Menu> Solution> Physics> Environment> Read](https://www.ansys.com/)) command is issued to resume the fluid analysis, you reapply the transient ramp. You apply the inlet boundary velocity of 3.0 in/sec at 2.0 seconds and then indicate that this is an “old” condition by issuing the following:

**Command(s):** FLOCHECK,2
**GUI:** Main Menu> Preprocessor> FLOTRAN Set Up> Flocheck

This means that the 3.0 in/sec inlet boundary condition at 2 seconds is the starting point for a ramp. You then input the final point of the ramp, 5.0 in/sec at 4 seconds, and specify a ramped boundary condition by issuing the following:

**Command(s):** FLDATA4,TIME,BC,1
**GUI:** Main Menu> Preprocessor> FLOTRAN Set Up> Execution Ctrl

You execute the transient analysis as usual using the **SOLVE** command.

For more information about applying transient boundary conditions with FLOTRAN, see Chapter 5, “FLOTRAN Transient Analyses”.

<table>
<thead>
<tr>
<th>Structural</th>
<th>Thermal</th>
<th>Magnetic</th>
<th>Electrostatic</th>
<th>Fluid</th>
<th>Electric Conduction</th>
</tr>
</thead>
<tbody>
<tr>
<td>PLANE82</td>
<td>PLANE77</td>
<td>PLANE53</td>
<td>PLANE121</td>
<td>-</td>
<td>PLANE67</td>
</tr>
<tr>
<td>SHELL63,</td>
<td>SHELL57,</td>
<td>-</td>
<td>-</td>
<td>-</td>
<td>SHELL157</td>
</tr>
<tr>
<td>SHELL181</td>
<td>SHELL131</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>SHELL91,</td>
<td>SHELL132</td>
<td>-</td>
<td>-</td>
<td>-</td>
<td>SHELL93</td>
</tr>
<tr>
<td>SHELL93</td>
<td></td>
<td></td>
<td></td>
<td></td>
<td>SHELL63, SHELL181</td>
</tr>
<tr>
<td>LINK8</td>
<td>LINK33</td>
<td>-</td>
<td>-</td>
<td>FLUID116</td>
<td>LINK68</td>
</tr>
</tbody>
</table>
2.4. Performing a Sequentially Coupled Physics Analysis with Physics Environments

This section outlines the physics environment approach to a sequentially coupled physics analysis.

1. Build a model that meets the requirements of each physics discipline that will be addressed. Keep the following points in mind:

   - Each ANSYS solid model area or volume defined has its own particular needs with respect to element type, material properties, and real constants. All solid model entities should have element type numbers, real constant set numbers, material numbers, and element coordinate system numbers applied. (Their meaning will change according to the physics environment.)
   - Certain groups of areas or volumes will be used in two or more different physics environments. The mesh you use must be suitable for all environments.

2. Create the physics environment. You perform this step for each physics discipline that is part of the sequentially coupled physics analysis.

   - Refer to various sections of the ANSYS Analysis Guides as necessary to determine what you should specify for a particular physics analysis.
   - Define the necessary element types to be used in a physics simulation (for example, ET,1,141 or ET,2,142, etc., for a FLOTTRAN simulation, ET,1,13 or ET,2,117 for a magnetic solution, etc.). Set the "null" element type (Type = 0, i.e. ET,3,0) for use in regions not associated (or needed) for a given physics. Elements assigned to the null element type are ignored during solution.
   - Assign material properties, real constant set data, and element coordinate systems as needed, in accordance with the established attribute numbers defined earlier for the model.
   - Assign attribute numbers for element type, materials, real constants, and element coordinate systems to the solid model areas or volumes (using the AATT command (Main Menu> Preprocessor> Meshing> Mesh Attributes> All Areas or Picked Areas) or the VATT command (Main Menu> Preprocessor> Meshing> Mesh Attributes> All Volumes or Picked Volumes)).
   - Apply the nominal loads and boundary conditions. These conditions are those that are the same (for a steady state problem) for each execution of this physics analysis in the overall iterative procedure.
   - Set all the solution options.
   - Choose a title for the physics environment and issue the PHYSICS,WRITE command with that title. For example, in a fluid-magnetics analysis, you could use the following command to write out the fluid physics environment:
     
     Command(s): PHYSICS,WRITE,Fluids
     GUI: Main Menu> Preprocessor> Physics> Environment> Write
   
   - Clear the database of the present physics environment in order to create the next physics environment. This is done by issuing the PHYSICS,Clear option.
     
     Command(s): PHYSICS,Clear
     GUI: Main Menu> Preprocessor> Physics> Environment> Clear
   
   - Prepare the next physics environment as noted above.
   - Issue SAVE to save the database and physics file pointers.

Assuming that the jobname for this multiphysics analysis is "Induct" and these are the first two physics environment files written, the files would be named Induct.PH1 and Induct.PH2. For more information about the PHYSICS command, see the ANSYS Commands Reference.
3. Perform the sequentially coupled physics analysis, performing each physics analysis in turn.

/SOLU ! Enter solution
PHYSICS,READ,Magnetics ! Contains magnetics environment
SOLVE
FINISH
/SOLU
PHYSICS,READ,Fluids
LDREAD,FORCE,,,2,,rmg ! Magnetic Lorentz forces
SOLVE

The extensions on the LDREAD command are associated with the results file which is being read in. Results from a thermal analysis would be read in from a Jobname.RTH file. All other results besides magnetics and fluids would come from a Jobname.RST file.

2.4.1. Mesh Updating

Many times a coupled-field analysis involving a field domain (electrostatic, magnetic, fluid) and a structural domain yields significant structural deflections. In this case, to obtain an overall converged coupled-field solution it is often necessary to update the finite element mesh in the non-structural region to coincide with the structural deflection and recursively cycle between the field solution and structural solution.

Figure 2.3: “Beam Above Ground Plane” illustrates a typical electrostatic-structural coupling problem requiring mesh updating. In this problem, a beam sits above a ground plane at zero potential. A voltage applied to the beam causes it to deflect (from electrostatic forces) toward the ground plane. As the beam deflects, the electrostatic field changes, resulting in an increasing force on the beam as it approaches the ground plane. At a displaced equilibrium, the electrostatic forces balance the restoring elastic forces of the beam.

**Figure 2.3  Beam Above Ground Plane**

To run a simulation of this problem requires adjustment of the field mesh to coincide with the deformed structural mesh. In ANSYS, this adjustment is known as mesh morphing.

To accomplish mesh morphing, you issue the DAMORPH command (morphing elements attached to areas), DVMORPH command (morphing elements attached to volumes, or the DEMORPH command (morphing selected elements). You use the RMSHY option to specify one of the following three ways of mesh morphing:

- Morphing - The program moves nodes and elements of the "field" mesh to coincide with the deformed structural mesh. In this case, it does not create any new nodes or elements or remove any nodes or elements from the field region.
- Remeshing - The program removes the field region mesh, and replaces it with a new mesh that coincides with the deformed structural mesh. Remeshing does not alter the structural mesh. It connects the new field mesh to the existing nodes and elements of the deformed structural mesh.
- Morphing or Remeshing - The program attempts to morph the field mesh first. If it fails to morph, the program switches to remeshing the selected field region. This is the default.

Mesh morphing affects only nodes and elements. It does not alter solid model entity geometry locations (keypoints, lines, areas, volumes). It retains associativity of the nodes and elements with the solid modeling entities. Nodes
and elements attached to keypoints, lines, and areas internal to a region selected for morphing may in fact move off of these entities, however, the associativity will still remain.

You must exercise care when applying boundary conditions and loads to a region of the model undergoing mesh morphing. Boundary conditions and loads applied to nodes and elements are appropriate only for the morphing option. If boundary conditions and loads are applied directly to nodes and elements, the **DAMORPH**, **DVMORPH**, and **DEMORPH** commands require that these be removed before remeshing can take place. Boundary conditions and loads applied to solid modeling entities will correctly transfer to the new mesh. Since the default option may morph or remesh, you are better off assigning only solid model boundary conditions to your model.

You must also exercise care with initial conditions defined by the **IC** command. Before a structural analysis is performed, the **DAMORPH**, **DVMORPH**, and **DEMORPH** commands require that initial conditions be removed from all null element type nodes in the non-structural regions. Use **ICDELE** to delete the initial conditions.

The morphing algorithm uses the ANSYS shape checking logic to assess whether the element is suitable for subsequent solutions. It queries the element type in the morphing elements for shape checking parameters. In some instances, the elements in the morphing region may be the null element type (Type 0). In this case, the shape checking criteria may not be as rigorous as the shape checking criteria for a particular analysis element type. This may result in elements failing the shape checking test during the analysis phase of a subsequent solution in the field domain. To avoid this problem, reassign the element type from the null element type prior to issuing the morphing command.

Displacements results from a structural analysis must be in the database prior to issuing a morphing command. Results are in the database after a structural solution, or after reading in the results from the results file (**SET** command in **POST1**). The structural nodes of the model move to the deformed position from the computed displacements. If you are performing a subsequent structural analysis, you should always restore the structural nodes to their original position. You can accomplish this by selecting the structural nodes and issuing **UPCOORD** with a **FACTOR** of -1.0.

**Command(s): UPCoord, Factor**

**GUI: Main Menu> Solution> Load Step Opts> Other> Updt Node Coord**

Mesh morphing supports all 2-D models meshed with quadrilateral and triangular lower and higher order elements. For 2-D models, all nodes and elements must be in the same plane. Arbitrary curved surfaces are not supported. In 3-D, only models with the following shape configurations and morphing options are supported.

- All tetrahedral elements - (morphing and remeshing supported)
- All brick elements - (morphing supported)
- All wedge elements - (morphing supported)
- Combination of pyramid-tetrahedral elements - (morphing supported)
- Combination of brick-wedge elements - (morphing supported)

Mesh morphing will most likely succeed for meshes with uniform-sided elements (such as those created with the **SMRTSIZE** command option). Highly distorted elements may fail to morph.

Figure 2.4: “Area Model of Beam and Air Region” illustrates a beam region immersed within an electrostatic region. Area 1 represents the beam model and Area 2 represents the electrostatic region. In this scenario, you would select Area 2 for morphing.
In many instances, only a portion of the model requires morphing (that is, the region in the immediate vicinity of the structural region). In this case, you should only select the areas or volumes in the immediate vicinity of the structural model. Figure 2.5: “Area Model of Beam and Multiple Air Regions” illustrates the beam example with multiple electrostatic areas. Only Area 3 requires mesh morphing. In order to maintain mesh compatibility with the nonmorphed region, the morphing algorithm does not alter the nodes and elements at the boundary of the selected morphing areas or volumes. In this example, it would not alter the nodes at the interface of Areas 2 and 3.

To perform mesh morphing at the end of a structural analysis, issue the following:

**Command(s):** DAMORPH, DVMORPH, DEMORPH

**GUI:**
- Main Menu> Preprocessor> Meshing> Modify Mesh> Refine At> Areas
- Main Menu> Preprocessor> Meshing> Modify Mesh> Refine At> Volumes
- Main Menu> Preprocessor> Meshing> Modify Mesh> Refine At> Elements

An alternative command, MORPH, may be used for mesh morphing. It is generally more robust than the DAMORPH, DVMORPH, and DEMORPH commands and it can be used with all element types and shapes. To prepare a non-structural mesh for morphing with the MORPH command, perform the following steps:

1. Create the non-structural model and mesh.
2. Activate the morphing command (MORPH,ON).
3. Apply appropriate structural boundary condition constraints to the boundary of the non-structural mesh (typically, you set normal components of displacement to zero).

*Note* — Morphed fields must be in the global Cartesian system (CSYS = 0).
See Section 2.7: Example Fluid-Structural Analysis Using Physics Environments for a problem using mesh morphing and physics files.

### 2.4.2. Restarting an Analysis Using a Physics Environment Approach

In many sequential coupling applications there is a need to restart one of the physics solutions. For example, in induction heating, you need to restart the transient thermal analysis during the sequential coupling cycles. For static nonlinear structural coupled-field analysis, it is advantageous to restart the structural solution rather than start all over. You can implement a restart procedure easily within a sequential coupled-field analysis. A restart requires the EMAT, ESAV, and DB files of the particular physics. You can isolate EMAT and ESAV files for the particular physics by using the /ASSIGN command. The database file will be consistent with the physics when the physics environment approach is used. Following is a summary of the restart procedure:

1. Use the /ASSIGN command to redirect the file assignment for the EMAT and ESAV files prior to solving the physics domain requiring a restart.
2. Perform the restart analysis.
3. Use the /ASSIGN command to redirect the file assignments for the EMAT and ESAV files to their default values for use by the other physics domains.

The induction heating example problem described later on in the chapter demonstrates the use of a transient restart thermal analysis.

### 2.5. Example Thermal-Stress Analysis Using the Indirect Method

The example described in this section demonstrates a simple thermal-stress analysis performed using the indirect method.

#### 2.5.1. The Problem Described

In the example problem, two long, thick-walled cylinders, concentric about the cylinder axis, are maintained at a temperature \( T_i \) on the inner surface and on the outer surface \( T_o \). The object of the problem is to determine the temperature distribution, axial stress, and hoop stress in the cylinders.
### Geometric Properties

<table>
<thead>
<tr>
<th>Outer Cylinder (aluminum)</th>
<th>Inner Cylinder (steel)</th>
</tr>
</thead>
<tbody>
<tr>
<td>a = 0.1875 in.</td>
<td>a = 2.2 x 10^{-5} in/in°F</td>
</tr>
<tr>
<td>b = 0.40 in.</td>
<td>ν = 0.33</td>
</tr>
<tr>
<td>c = 0.60 in.</td>
<td>K = 10.8 btu/hr-in-°F</td>
</tr>
<tr>
<td>T_i = 200°F</td>
<td>E = 10.6 x 10^6 psi</td>
</tr>
<tr>
<td>T_o = 70°F</td>
<td>α = 0.3</td>
</tr>
</tbody>
</table>

### Material Properties

- **Aluminum (Outer Cylinder)**
  - E = 30 x 10^6 psi
  - α = 0.65 x 10^{-5} in/in°F
  - ν = 0.3
  - K = 2.2 btu/hr-in-°F

- **Steel (Inner Cylinder)**
  - E = 10.6 x 10^6 psi
  - α = 1.35 x 10^{-5} in/in°F
  - ν = 0.33
  - K = 10.8 btu/hr-in-°F

The basic procedure for the indirect method in this problem is as follows:

1. Define and solve the thermal problem.
2. Return to PREP7 and modify the database. You will need to switch element types, specify additional material properties, and specify structural boundary conditions.
3. Read the temperatures from the thermal results file.
4. Solve the structural problem.

The command text below demonstrates the problem input. All text prefaced with an exclamation point (!) is a comment.

```plaintext
/batch,list
/show
/title, thermal stress in concentric cylinders - indirect method
/prep7
et,1,plane77,1  ! PLANE77 axisymmetric option
mp,kxx,1,2.2    ! Steel conductivity
mp,kxx,2,10.8   ! Aluminum conductivity
rectng,.1875,.4,0,.05! Model
rectng,.4,.6,0,.05
aglue,all
numcmp,area
asel,s,area,1   ! Assign attributes to solid model
aatt,1,1,1
asel,s,area,2
aatt,2,1,1
asel,all
esize,.05
amesh,all
! Mesh model
nsel,s,loc,x,.1875
    d,all,temp,200  ! Apply thermal loads
nsel,s,loc,x,.6
    d,all,temp,70
nsel,all
finish
/solu
solve
finish
/post1
path,radial,2    ! Define path name and number of path points
ppath,1,.1875   ! Define path by location
ppath,2,.6
pdef,temp,temp  ! Interpret temperature to path
pasave,radial,filea ! Save path to an external file
plpath,temp      ! Plot temperature solution
finish
/prep7
et,1,82,1        ! Switch to structural element, SOLID82
mp,ex,1,30e6     ! Define structural steel properties
mp,alpx,1,.65e-5
mp,nuxy,1,.3
mp,ex,2,1.35e-5
mp,alpx,2,.33
mp,nuxy,2,.33
nsel,s,loc,y,.05
    cp,1,uy,all  ! Apply structural boundary conditions
```
2.6. Example Thermal-Stress Analysis Using Physics Environments

This section shows you how to solve the same thermal-stress problem covered in the previous section, this time using the physics environment approach. In this particular case, it may not be advantageous to use the physics environment approach because the problem is a simple one-way coupling. However, it will allow for quick switching between physics environments for subsequent modeling or analysis.

The basic procedures for the physics environment approach in this problem is shown below:

1. Define the thermal problem.
2. Write the thermal physics file.
3. Clear boundary conditions and options.
4. Define the structural problem.
5. Write the structural physics file.
6. Read the thermal physics file.
7. Solve and postprocess the thermal problem.
8. Read the structural physics file.
9. Read the temperatures from the thermal results file.
10. Solve and postprocess the physics file.

The command text shown below demonstrates the problem input. All text prefaced with an exclamation point (!) is a comment.

```plaintext
nset,s,loc,x,.1875
cp,2,ux,all
nset,s,loc,y,0
d,all,uy,0
nset,all
finish
/solu
tref,70
ldread,temps,,rth ! Read in temperatures from thermal run
solve
finish
/post1
paresu,radial,filea !Restore path
pmap,,mat ! Set path mapping to handle material discontinuity
pdef,sx,s,x ! Interpret radial stress
pdef,sz,s,z ! Interpret hoop stress
plpath,sx,sz ! Plot stresses
plpagg,sx,,node ! Plot radial stress on path geometry
finish
```

The command text shown below demonstrates the problem input. All text prefaced with an exclamation point (!) is a comment.
esize,.05
amesh,all
! Mesh model
nsel,s,loc,x,.1875
d,all,temp,200
! Apply thermal loads
nsel,s,loc,x,.6
d,all,temp,70
nsel,all
physics,write,thermal
! Write the thermal physics file
physics,clear
! Clear all bc's and options
et,1,82,,,1
! Switch to structural element, SOLID82
mp,ex,1,30e6
! Define structural steel properties
mp,alpx,1,.65e-5
mp,nuxy,1,.3
mp,ex,2,10.6e6
mp,alpx,2,1.35e-5
mp,nuxy,2,.33
nsel,s,loc,y,.05
! Apply structural boundary conditions
cp,1,uy,all
nsel,s,loc,x,.1875
cp,2,ux,all
nsel,s,loc,y,0
d,all,uy,0
nsel,all
tref,70
physics,write,struct
! Write structural physics file
save
! Save database
finish
/solu
physics,read,thermal
! Read thermal physics file
solve
! Solve thermal problem
save,thermal,db
! Save thermal model for subsequent postprocessing
finish
/post1
path,radial,2
! Define path name and number of path points
ppath,1,,,1.875
! Define path by location
ppath,2,,.6
pdef,temp,temp
! Interpret temperature to path
pasave,radial,filea
! Save path to an external file
plpath,temp
! Plot temperature solution
finish
/solu
physics,read,struct
! Read structural physics file
ldread,temp,,,,,rth
! Read in temperatures from thermal run
solve
! Solve structural problem
finish
/post1
paresu,radial,filea
! Restore path
pmap,,mat
! Set path mapping to handle material discontinuity
pdef,sx,s,x
! Interpret radial stress
pdef,sz,s,z
! Interpret hoop stress
plpath,sx,sz
! Plot stresses
plpam,sx,,node
! Plot radial stress on path geometry
finish
Figure 2.6 Stress Profile Across Material Discontinuity

thermal stress in concentric cylinders - Physics Environment Method
2.7. Example Fluid-Structural Analysis Using Physics Environments

The example in this section illustrates a steady-state fluid-structure interaction problem. This problem demonstrates the use of nonlinear large-deflection structural coupling for a fluid domain as well as the use of the "null" element type in a physics environment setting. It also demonstrates mesh morphing.

2.7.1. The Problem Described

A channel containing a rubber gasket is subjected to water flowing with an inlet velocity of 0.35 m/sec. (See Figure 2.8: “Diagram of a Channel Obstruction Analysis” below) The object of the problem is to determine the pressure drop and gasket deflection under steady-state conditions. The problem is completely described by the input listing provided at the end of this section.

2.7.2. The Procedure

Build a model of the fluid-structural entity to be analyzed. For this example problem, you would model three regions: (a) the gasket, (b) a small fluid region around the gasket that requires mesh morphing, and (c) the remaining fluid region. Figure 2.8: “Diagram of a Channel Obstruction Analysis” below depicts the model:
Figure 2.8 Diagram of a Channel Obstruction Analysis

The gasket will deform due to the fluid pressure. The deflection may be significant enough to affect the flow field. In this case, the example defines a small fluid region around the gasket used by a fluid physics environment. By solving a structural analysis in the structural region, you obtain the gasket displacements that you need to morph the small region around the gasket. You then use the morphed mesh in a subsequent fluid analysis. The fluid analysis uses null type elements for the gasket and the structural analysis uses null type elements for the fluid.

The following sections discuss the procedure for the coupled fluid-structural problem.

2.7.2.1. Build the Model

Build the model of the entire domain, including the fluid regions and the gasket region.

You assign attribute numbers to distinguish element types, material properties and real constant sets to each area using the AATT command. Table 2.3: “Physics Environment Attributes” shows the assignments for this problem. All areas that will at sometime represent fluid regions are assigned material number 1. Real constant sets are provided for but not used in this problem.

Table 2.3 Physics Environment Attributes

<table>
<thead>
<tr>
<th>Region</th>
<th>Type</th>
<th>Mat</th>
<th>Real</th>
</tr>
</thead>
<tbody>
<tr>
<td>Gasket</td>
<td>2</td>
<td>2</td>
<td>2</td>
</tr>
<tr>
<td>Fluid</td>
<td>1</td>
<td>1</td>
<td>1</td>
</tr>
</tbody>
</table>

2.7.2.2. Create Fluid Physics Environment

To do so, assign element types and define material properties for the fluid region as shown in Table 2.4: “Fluid Physics Environment”: 
Here is where you define the material properties of water using FLDATA commands. Solution controls such as the number of iterations in the initial FLOTRAN analysis are defined. The turbulence option is activated. See the input listing for further details.

**Table 2.4 Fluid Physics Environment**

<table>
<thead>
<tr>
<th>Region</th>
<th>Type</th>
<th>Mat</th>
<th>Real</th>
</tr>
</thead>
<tbody>
<tr>
<td>Gasket</td>
<td>Null type (0)</td>
<td>none</td>
<td>none</td>
</tr>
<tr>
<td>Fluid</td>
<td>FLUID141</td>
<td>Viscosity, density</td>
<td>none</td>
</tr>
</tbody>
</table>

- Assign appropriate nominal fluid boundary conditions and loads, as shown in Figure 2.9: “Nominal Fluid Physics Boundary Conditions” below:

**Figure 2.9 Nominal Fluid Physics Boundary Conditions**

- Fluid boundary conditions are applied, in this case to the solid model. The input file contains a definition of a named component of nodes representing the bottom of the gasket. You can list the nodal locations of these nodes periodically in the solution process to monitor their movement. In this example, line 1 represents the bottom of the gasket. Select the nodes associated with this line and then name them "gasket."

  **Command(s):** CM,GASKET,NODES  
  **GUI:** Utility Menu> Select> Comp/Ass'y> Create Component

- Write the fluid physics environment to a file.

  **Command(s):** PHYSICS,WRITE,FLUID,FLUID  
  **GUI:** Main Menu> Preprocessor> Physics> Environment> Write
2.7.2.3. Create Structural Physics Environment

- Clear away all the information specified for the fluid environment in preparation for defining the structures environment.
  
  **Command(s):** PHYSICS,CLEAR
  
  **GUI:** Main Menu > Preprocessor > Physics > Environment > Clear

- Change the element types for the regions from fluid to structural by reassigning the element type numbers and KEYOPT options as shown in Table 2.4: “Fluid Physics Environment”. FLUID141 should become PLANE42. Specify the null element type (0) for the fluid region, because it is not required for the structural physics environment.

<table>
<thead>
<tr>
<th>Region</th>
<th>Type</th>
<th>Mat Type</th>
<th>Real</th>
</tr>
</thead>
<tbody>
<tr>
<td>Gasket</td>
<td>PLANE182</td>
<td>Mooney-Rivlin</td>
<td>none</td>
</tr>
<tr>
<td>Fluid</td>
<td>Null type (0)</td>
<td>none</td>
<td>none</td>
</tr>
</tbody>
</table>

- Define structural properties for each physics region required for the structural analysis. (See Table 2.5: “Structural Physics Environment”.)

- Apply boundary conditions to the structure. (See Figure 2.10: “Nominal Structural Physics Boundary Conditions” below.)

**Figure 2.10 Nominal Structural Physics Boundary Conditions**

- Define appropriate load step and solution options.

- Write the structural physics environment to a file (e.g., PHYSICS,WRITE,STRUC,STRUC).
2.7.2.4. Fluid/Structure Solution Loop

Either interactively or in a batch mode (see the input listing), a fluid-structure solution loop is entered. In this case, the maximum gasket displacement (MGD) becomes the overall convergence monitor. When the MGD change between two consecutive structural executions is less than the tolerance value, the case is terminated.

The initial FLOTRAN analysis should be executed until well converged. Subsequent analyses will restart from this solution and should not need nearly as many global iterations to converge. Also, the second and subsequent structural analyses will be restarts.

After each structural analysis, mesh morphing is executed to move the nodes in the small fluid region around the gasket to conform to the structural displacements. These new node locations are inputs for the subsequent flow analysis. For a proper structural solution and further morphing, all nodes must be returned to their original positions before applying the updated pressures from a flow analysis.

Steps in the solution loop include:

1. Read in the fluid physics environment.
   Command(s): PHYSICS,READ,fluid
   GUI: Main Menu> Solution> Physics> Environment> Read

2. Change any FLOTRAN parameters necessary (e.g., the number of global iterations requested.)
   Command(s): FLDATA2,ITER,EXEC,100
   GUI: Main Menu> Solution> FLOTRAN Setup> Execution Control

3. Solve with FLOTRAN.
   Command(s): SOLVE
   GUI: Main Menu> Solution> Run FLOTRAN

4. Read in the structural environment.
   Command(s): PHYSICS,READ,struct
   GUI: Main Menu> Solution> Physics> Environment> Read

5. Perform /ASSIGN as necessary for restarting the structural run.
   Command(s): /ASSIGN,esave,struc,esav /ASSIGN,emat,struc,emat
   GUI: Utility Menu> File> ANSYS File Options

6. Put the nodes back to their original positions for the subsequent nonlinear structural analysis and future morphing.
   Don’t execute this step for the first fluid-structure solution loop.
   Command(s): PARSAV,ALL
   GUI: Utility Menu> Parameters> Save Parameters
   Command(s): RESUME
   GUI: Utility Menu> File> Resume Jobname.db
   Command(s): PARRES
   GUI: Utility Menu> Parameters> Restore Parameters

7. Restart the analysis.
   Don’t execute this step for the first fluid-structure solution loop.
   Command(s): ANTYPE,STATIC,REST
   GUI: Main Menu> Solution> Restart

8. Select nodes/elements to which pressure loads from the FLOTRAN analysis will be applied.

9. Execute the LDREAD command.
   Command(s): LDREAD,PRES,LAST,,,,,rfl
10. Set option to not use multiframe restart files.
   Command(s): RESCONTROL,,NONE
   GUI: Main Menu> Solution> Nonlinear> Restart Control

11. Solve the structural analysis and save the database on the first step for further resume.
   Command(s): SOLVE
   GUI: Main Menu> Solution> Solve
   Command(s): SAVE
   GUI: Utility Menu> File> Save as Jobname.db

12. Perform mesh morphing in the small fluid region around the gasket (component name AREA2).
   Command(s): DAMORPH,AREA2,,2
   GUI: Main Menu> Preprocessor> Meshing> Modify Mesh> Refine At> Areas

13. Evaluate the mesh motion compared to the last time. Select the named component GASKET and list the nodal coordinates.

14. Check convergence by comparing consecutive maximum gasket displacement (MGD) values.

15. View the element plots in file gasket.grph.

### 2.7.3. Results

The fluid-structure solution loop was executed until the convergence criteria were met. A convergence tolerance of 0.5% was used. For the first analysis, 400 global iterations were sufficient to converge the FLOTRAN solution. In the Fluid Structure interaction loop, the number of iterations was set to 100 for the remaining FLOTRAN runs.

Figure 2.11: “Streamlines Near Gasket” depicts the streamlines near the gasket for the deformed geometry and Figure 2.12: “Pressure Contours”, the pressure contours. Qualitatively, the results will look similar for the undeformed (first analysis) and deformed (final analysis) cases.

**Figure 2.11 Streamlines Near Gasket**
Finally, Figure 2.13: “von Mises Stress in Gasket” shows the von Mises stress obtained in the final analysis. The peak stress in the final analysis is approximately 25% less than the peak stress in the first analysis. This indicates that considering the effect of the displaced geometry on the flow field made a significant difference.

Before plotting structural results the structural nodes should be returned to their original positions.  
**Command(s):**  
**ANSYS**  
**GUI:**  
Main Menu> Solution> Load Step Opts> Other> Updt Node Coord

**Figure 2.13 von Mises Stress in Gasket**
!! 1. Build the model of the entire domain:
!!    Fluid region - static mesh
!!    Gasket leaves a hole in the center of the duct
!!    Morphing Fluid region is a user defined region around
!!    the gasket. The fluid mesh here will deform and be
!!    updated as the gasket deforms.
!!
!! Parameterize Dimensions in the flow direction
!!
yent = 0.0       ! Y coordinate of the entrance to the pipe
dyen = 1.0       ! Undeformed geometry flow entrance length
ysf1 = yent+dyen ! Y coordinate of entrance to the morphing fluid region
dsf1 = 0.5       ! Thickness of upstream
ygas = ysf1+dsf1 ! Y coordinate of the bottom of the gasket
gs = 0.02        ! Thickness of the gasket
dg2=gs/2.
ytg = ygas+dg    ! Y coordinate of the initial top of the gasket
dsf2 = 0.5       ! Thickness of downstream region
ysf2 = ytg + dsf2 ! Y of Top of the downstream morphing fluids region
dyex = 6.0       ! Exit fluid length
x = 0.           ! Location of the axisymmetric Centerline
dgass = 0.20     ! Initial span of gasket
piper = 0.3      ! Radius of the pipe
xgap = piper-dgasr! radius of completely unobtructed flow passage
!!
!!! Create geometry
!!
rect,xgap,piper,ygas,ytg     ! A1:Gasket (keypoints 1-4) 
rect,x,piper,ysf1,ysf2       ! A2: Morphing fluid region
rect,x,piper,yent,ysf1       ! A3: Fluid region with static mesh
rect,x,piper,ysf2,ysf2+dyex  ! A4: Fluid region with static mesh
ovlap,all
k,22,xgap+dg2,ygas+dg2     
rect,xgap+dg2,ygas+dg2
rarc = dg2*1.1
larc,1,4,22,rarc
al,6,4
adelete,7
al,6,3,22,7,8,5,21,1

!!Mesh Division information
ngap = 10       ! Number elements across the gap
ngas = 10       ! Number of elements along the gasket
rgs = -2        ! Spacing ratio along gasket
nflu = ngap+ngas ! Number of elements across the fluid region
raflu = -3      ! Space fluid elements near the walls and center
nenty =8        ! Elements along flow - entrance
raent = 5          ! Size ratio in the inlet region
nf1 = 20         ! Elements along flow - first morph.fluid.
nthgas = 4        ! Elements in the gasket
nf2 = 3         ! Elements along flow - second morph.fluid.
next = 30       ! Elements along flow - exit region
rext = 6        ! Size ratio in flow direction of outlet
rafls = 12      ! Initial element spacing ratio - morph.fluid
lesize,1,,,ngas,rgas
lesize,3,,,ngas,rgas
nf1= nf1*2+9
lesize,all,,,nthgas
alls
lesize,5,,,nflu,raflu
lesize,7,,,nflu,raflu
lesize,9,,,nflu,raflu
lesize,15,,,nflu,raflu
lesize,18,,,nenty,1./raent
lesize,17,,,nenty,1./raent
lesize,21,,,nf1,rafls
lesize,8,,,nf1,1./(rafls+3)
lesize,22,,,nf1,rafls
lesize,19,,,next,rext
lesize,20,,,next,rext

!!! AATT,MAT,REAL,TYPE     - Set the attributes for the areas
asel,s,,,1,2
aatt,2,2,2    ! Gasket   (material 2)
asel,s,,,3
cm,area2,area
alist    ! List area selected for further morphing
asel,a,,,5,6
aatt,1,1,1    ! Fluid area (material 1)
alls
eshape,2
asel,u,,,2,3
amesh,all
eshape,0
asel,s,,,2,3
amesh,all
!-----------------
!!!!!  Create element plot and write to the file gasket.grph
asel,s,,,1,3
esla,s
/Title, Initial mesh for gasket and neighborhood
eplot
/ZOOM,1,RECT,0.3,-0.6,0.4,-0.5
alls
!-----------------
!!!  2. Create Physics Environment for the Fluid
et,1,141
et,2,0        ! Gasket becomes the Null Element
vin=3.5e-1    ! Inlet water velocity (meters/second)
!!           CFD Solution Control
flda,solu,flow,1
flda,solu,turb,1
flda,iter,exec,400
flda,outp,sumf,10
!!           CFD Property Information
flda,nomi,dens,constant
flda,nomi,visc,constant
flda,conv,pres,1.E-8   ! Tighten pressure equation convergence
!!    CFD Boundary Conditions (Applied to Solid Model)
lsel,s,,,8,17,9
lsel,a,,,20
d1,all,,vx,0.,1      ! Centerline symmetry
lsel,s,,,9
Chapter 2: Sequentially Coupled Physics Analysis

dl,all,vx,0,1
dl,all,vy,vin,1  ! Inlet Condition
isel,s,,,2
isel,a,,,18,19
isel,a,,,21,22

dl,all,vx,0,1  ! Outer Wall
dl,all,vy,0,1
isel,s,,,1,3,2
isel,a,,,6

dl,all,vx,0,1  ! Gasket
dl,all,vy,0,1
isel,s,,,15

dl,15,pres,0,1  ! Outlet pressure condition

!!! create named component of nodes at the bottom of gasket
isel,s,,,1
nsll,,1
cm,gasket,node
nlist ! List initial nodal positions of the bottom of the gasket

/com, +++++++++ STARTING gasket coordinates ------

alls
/title,Fluid Analysis
physics,write,fluid,fluid
!!
!!!! 3. Create Physics Environment for the Structure
!!
physics,clear
et,1,0  ! The Null element for the fluid region
et,2,56  ! Gasket element - material 2
mp,ex,2,2.82E+6  ! Young's modulus for rubber
mp,nuxy,2,0.49967  ! Poisson's ratio for the rubber
tb,mooney,2
tbdata,1,0.293E+6  ! Mooney-Rivlin Constants
  "     "        "
tbdata,2,0.177E+6  !    "     "        "

isel,s,,,2
nsll,,1
d,all,ux,0.
d,all,uy,0.  ! Fix the end of the gasket
alls

/title,structural analysis
finish
/solu
antype,static
ngeom,on
cnvtol,f,,,,-1
physics,write,struc,struc
physics,clear
save
!!
!!!! 4. Fluid-Structure Interaction Loop
!!
loop=25               ! Maximum allowed number of loops
toler=0.005           ! Convergence tolerance for maximum displacement
*dim,dismax,array,loop   ! Define array of maximum displacement values
*dim,strcri,array,loop   ! Define array of convergence values
*dim,index,array,loop
*do,i,1,loop             ! Execute fluid -> structure solutions
/solu
physics,read,fluid  ! Read in fluid environment
*if,i,ne,1,then
flda,iter,exec,100  ! Execute 100 global iterations for
*endif  ! each new geometry
solve  ! FLOTRAN solution
fini
! end of fluid portion
physics,read,struc  ! Read in structures environment
/assign,esave,struc,esav ! Files for restarting nonlinear structure
/assign,emat,struc,emat
*if,i,gt,1,then ! Structural restart loop
parsave,all ! Save parameters for convergence check
resume ! Resume DB - to return original node positions
parresume ! Resume parameters needed for convergence check
/prep7
antype,stat,rest
fini
*endif

/solu
solec,off
lsel,s,,,1,3,2 ! Select proper lines to apply fluid pressures
lsel,a,,,6 ! to the entire gasket surface
nsll,,1
esel,s,type,,2
ldread,pres,last,,,,,rfl ! Apply pressure surface load from Flotran
alls
rescontrol,,none ! Do not use multiframe restart for nonlinear
solve
*if,i,eq,1,then
save ! save original node locations at the first run
*endif
fini

/post1
cmsel,s,gasket
nsort,u,sum,1,1
*get,dismax(i),sort,0,max ! Get the maximum displacement value
strcri(i)=toler*dismax(i)
alls
fini

/prep7
mkey=2 ! Select level of mesh morphing for fluid
damorph,area2, ,mkey ! Perform morphing of "morphing fluid"
!----------------
!!!!! Create element plot and write it in file gasket.grph
fini

/prep7
et,1,42
asel,s,,,1,3
esla,s
>Title, EPLOT after DAMORPH,area2, ,%mkey% step number %i%
eplot
alls
!----------------
.cmsel,s,gasket
nlist ! List updated coordinates of bottom of gasket for comparison
/com, ++++++++ UPDATED gasket coordinates -------
alls
fini
/assign,esav
/assign,emat

!!!!! Checking convergence criteria
imax=1
index(i)=1
*if,i,gt,1,then
strcri(i)=abs(dismax(i)-dismax(i-1))-toler*dismax(i-1)
*if,strcri(i),le,0,then
strcri(i)=0
*exit ! Stop looping if convergence is reached
*endif
*endif
*endo
!!!! End of the Computational loop
save ! Nodal coordinates of deformed geometry are saved
!!!!! Convergence printout
*vwrite
(/{Loop No. Max.Displacement Struct.Convergence'})
/nopr
*vlen,imax
2.8. Example Induction-heating Analysis Using Physics Environments

This example illustrates a transient induction heating problem. The problem demonstrates the use of a solution sequence alternating between an electromagnetic harmonic analysis and a transient heat transfer analysis with restarting.

2.8.1. The Problem Described

A very long steel billet undergoes surface heat treating by rapidly raising the temperature of the billet surface by means of an induction coil. The coil is placed in close proximity to the billet surface and is excited by a large alternating current at high frequency. The AC current induces heat in the billet, most notably at the surface, which quickly raises the surface temperature.

A simplified geometry considers only a finite length strip of the long billet, essentially reducing the problem to a one-dimensional study as shown in Figure 2.14: “Axisymmetric 1-D Slice of the Induction Heating Domain”.

Figure 2.14  Axisymmetric 1-D Slice of the Induction Heating Domain

2.8.2. The Procedure

The billet will heat up to over 700°C. This temperature dependency of the material properties must be considered for both the thermal problem and the electromagnetic problem. You must solve the problem sequentially, first doing an AC harmonic electromagnetic analysis and then a transient thermal analysis. In addition, you must repeat the electromagnetic analysis at various time intervals to correct for temperature dependent properties which
will affect the solution and hence the heating load to the billet. Figure 2.15: “Solution Flow Diagram” shows the solution flow diagram.

**Figure 2.15 Solution Flow Diagram**

The procedure for the induction heating problem is as follows.

**2.8.2.1. Step 1: Develop Attribute Relationship**

Develop an attribute relationship for the modeled regions as shown in Table 2.6: “Physics Environment Attributes”.

**Table 2.6 Physics Environment Attributes**

<table>
<thead>
<tr>
<th>Region</th>
<th>Type</th>
<th>Mat</th>
<th>Real</th>
</tr>
</thead>
<tbody>
<tr>
<td>Billet</td>
<td>1</td>
<td>2</td>
<td>1</td>
</tr>
<tr>
<td>Coil</td>
<td>2</td>
<td>3</td>
<td>1</td>
</tr>
<tr>
<td>Air</td>
<td>2</td>
<td>1</td>
<td>1</td>
</tr>
<tr>
<td>Billet surface</td>
<td>3</td>
<td>2</td>
<td>3</td>
</tr>
</tbody>
</table>
2.8.2.2. Step 2: Build the Model

Build the model of the entire domain. Assign the attributes to the different regions. (The billet surface will be used to define a surface effect element for thermal radiation. It will be handled differently than the solid regions.)

2.8.2.3. Step 3: Create Electromagnetic Physics Environment

Create the electromagnetic physics environment by defining element types and material properties as shown below.

**Table 2.7 Electromagnetic Physics Environment**

<table>
<thead>
<tr>
<th>Region</th>
<th>Type</th>
<th>Mat</th>
<th>Real</th>
</tr>
</thead>
<tbody>
<tr>
<td>Billet</td>
<td>PLANE13</td>
<td>MURX(T), RSVX(T)</td>
<td>None</td>
</tr>
<tr>
<td>Coil</td>
<td>PLANE13</td>
<td>MURX</td>
<td>None</td>
</tr>
<tr>
<td>Air</td>
<td>PLANE13</td>
<td>MURX</td>
<td>None</td>
</tr>
<tr>
<td>Billet surface</td>
<td>NULL Type (0)</td>
<td>None</td>
<td>None</td>
</tr>
</tbody>
</table>

- Assign appropriate nominal boundary conditions and loads as shown below.

**Figure 2.16 Nominal Electromagnetic Physics Boundary Conditions**

- Assign appropriate load step and solution options.
- Write the electromagnetic physics environment to a file.  
  
  **Command(s):** PHYSICS,WRITE  
  **GUI:** Main Menu > Preprocessor > Physics > Environment

2.8.2.4. Step 4: Create Thermal Physics Environment

Create the thermal physics environment as follows:

- Delete nominal boundary conditions and reset options.  
  
  **Command(s):** PHYSICS, CLEAR  
  **GUI:** Main Menu > Preprocessor > Physics > Environment

- Change the element types from electromagnetic to thermal as well as KEYOPT options. Specify the null element type in the air and coil region (assume the heat transfer analysis only considers the billet).

**Table 2.8 Thermal Physics Environment**

<table>
<thead>
<tr>
<th>Region</th>
<th>Type</th>
<th>Mat</th>
<th>Real</th>
</tr>
</thead>
<tbody>
<tr>
<td>Billet</td>
<td>PLANE55</td>
<td>KXX(T), ENTH(T)</td>
<td>None</td>
</tr>
<tr>
<td>Coil</td>
<td>NULL Type (0)</td>
<td>None</td>
<td>None</td>
</tr>
<tr>
<td>Air</td>
<td>NULL Type (0)</td>
<td>None</td>
<td>None</td>
</tr>
<tr>
<td>Billet surface</td>
<td>SURF151</td>
<td>EMIS</td>
<td>Stefan-Boltzmann Constant</td>
</tr>
</tbody>
</table>
• Define the thermal properties and real constants.
• Assign appropriate nominal boundary conditions and loads as shown below.

**Figure 2.17 Nominal Thermal Physics Boundary Conditions**

\[
\frac{\partial T}{\partial Y} = 0 \quad \text{Radiation} \; (T = 25^\circ \text{ C})
\]

\[
\frac{\partial T}{\partial X} = 0
\]

\[
\frac{\partial T}{\partial Y} = 0
\]

• Assign appropriate load step options and solution options

  **Command(s): PHYSICS,WRITE**
  GUI: Main Menu> Preprocessor> Physics> Environment> Write
  Main Menu> Solution> Physics> Environment> Write

2.8.2.5. Step 5: Write Thermal Physics Environment

Write the thermal physics environment to a file.

  **Command(s): PHYSICS,READ**
  GUI: Main Menu> Solution> Physics> Environment
  Main Menu> Solution> Physics> Environment> Read

2.8.2.6. Step 6: Prepare DO Loop

Prepare a *DO loop that will cycle between a harmonic electromagnetic analysis and a transient thermal analysis.

• Read in the electromagnetic physics environment and solve the harmonic analysis.
  **Command(s): SOLVE**
  GUI: Main Menu> Solution> Solve> Current LS

• Read in the temperatures and body force loads for material property evaluation.
  **Command(s): LDREAD**
  GUI: Main Menu> Preprocessor> Define Loads> Apply> Structural> Temperature> From Therm Analy

• Use /ASSIGN to redirect the file assignment for the **ESAV** and **EMAT** files for future use in a thermal transient restart.
  **Command(s): /ASSIGN**
  GUI: Utility Menu> File> ANSYS File Options

• Read in the thermal physics environment.
  **Command(s): PHYSICS,READ**
  GUI: Main Menu> Preprocessor> Physics> Environment> Read

• Read in the Joule heat generation rate from the electromagnetic analysis.
  **Command(s): LDREAD**
  GUI: Main Menu> Preprocessor> Define Loads> Apply> Thermal> Heat Generat> From Mag Analy

• Solve the thermal transient for a preset \( \Delta \) time increment.
2.8.2.7. Step 7: Repeat Prior Step

Repeat prior step for the next $\Delta t$ increment.

2.8.2.8. Step 8: Postprocess Results

Postprocess the problem results.

2.8.2.9. Command Input Listing

The command text below demonstrates the problem input. All text prefaced with an explanation point (!) is a comment.

```
/batch,list
/filenam, induc
/prep7
/shpp,off
/title, induction heating of a solid cylinder billet
/com,
et,1,13,,1       ! PLANE13, axisymmetric, AZ dof
et,2,13,,1
et,3,151,,1,1,1  ! SURF151, thermal, radiation
r,3,0            ! Real constant set for SURF151
row=.015         ! outer radius of workpiece
ric=.0175        ! inner radius of coil
roc=.0200        ! outer radius of coil
ro=.05           ! outer radius of model
t=.001           ! model thickness

freq=150000      ! frequency (Hz.)
pi=4*atan(1)     ! pi
cond=.392e7      ! maximum conductivity
muzero=4e-7*pi    ! free-space permeability
mur=200          ! maximum relative permeability
skind=sqrt(1/(pi*freq*cond*muzero* mur)) ! skin depth
ftime=3      ! final time
tinc=.05       ! time increment for harmonic analysis
time=0         ! initialize time
delt=.01       ! maximum delta time step

emunit,mks      ! set magnetic units
mp,murx,1,1     ! air relative permeability
mp,murx,3,1     ! coil relative permeability
mptemp,1,25.5,160,291.5,477.6,635,698 ! temps for relative permeability
mptemp,7,709,720,3,742,761,1000
mpdata,murx,2,1,200,190,182,161,135,104 ! steel relative permeability
mptemp
mptemp,1,0,125,250,375,500,625 ! temps for resistivity
mptemp,7,750,875,1000
mpdata,rsvx,2,1,1.84e-6, .272e-6, .384e-6, .512e-6, .656e-6, .824e-6
mpdata,rsvx,2,7,1.032e-6,1.152e-6,1.2e-6 ! steel resistivity

rectng,0,row,0,t ! billet
rectng,ric,row,0,t ! air-gap
rectng,ric,roc,0,t ! coil
rectng,roc,ro,0,t ! outer air
aglue,all
numcmp,area

ksel,s,loc,x,row ! select keypoints at outer radius of workpiece
kesize,all,skind/2 ! set meshing size to 1/2 skin depth
```
Section 2.8: Example Induction-heating Analysis Using Physics Environments

ksel,s,loc,x,0          ! select keypoints at center
kesize,all,40*skind     ! set meshing size
l sel,s,loc,y,t/2       ! select vertical lines
lesize,all,,1           ! set 1 division through thickness
l sel,all

asel,s,area,,1          ! set attributes for billet region
 aatt,2,1,1
asel,s,area,,3
 aatt,3,1,2
asel,s,area,,2,4,2
 aatt,1,1,2
asel,all
mshape,0,2d
mshk,1
amesh,1
l sel,s,loc,y,0
l sel,a,loc,y,t
l sel,u,loc,x,row/2
lesize,all,.001
l sel,all
amesh,all           ! mesh remaining areas

n                       ! create space node for SURF151
   *get,nmax,node,,num,max
l sel,s,loc,x,row
 type,3
real,3
mat,2
l mesh,all             ! mesh billet outer radius with SURF151
   *get,emax,elem,,num,max
emodif,emax,3,nmax      ! modify element to add space node for radiation
et,3,0                 ! reset type 3 to null element

n sel,s,loc,x          ! apply flux-normal b.c.
 n sel,all
es el,s,mat,,3
bfe,all,js,,,15e6       ! apply current density to coil
es el,all
finish
/solu
antyp,harm
harfrq,150000
physics,write,emag    ! write emag physics file
finish
/prep7
lsclear,all            ! clear all b.c.'s and options
 et,1,55,,1             ! PLANE55 thermal element, axisymmetric
 et,2,0                 ! null element type for coil and air region
 et,3,151,,1,1,1        ! SURF151 element for radiation
keyopt,3,9,1
r,3,1,5.67e-8          ! form factor, Stefan-Boltzmann constant

mptemp
mptemp,1,0,730,930,1000  ! temps for conductivity
mpdata,kxx,2,1,60.64,29.5,28,28
mptemp
mptemp,1,0,27,127,327,527,727
mptemp,7,765,765.001,927
mpdata,enth,2,1,0,91609056,453285756,1.2748e9,2.2519e9,3.3396e9
mpdata,enth,2,7,3.548547e9,3.548556e9,4.3520e9
mp,emis,2,.68             ! emissivity
finish
/solu
anty pe,trans
toffst,273

 tunif,100               ! initial uniform temperature
d,nmax,temp,25          ! ambient temperature
cnvtol,heat,1           ! convergence tolerance
 kbc,1                   ! step loads
 trnopt,full

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2.8.2.10. Results

Figure 2.18: “Temperature Response of Solid Cylinder Billet” shows the temperature results obtained in this analysis.
Figure 2.18 Temperature Response of Solid Cylinder Billet

induction heating of a solid cylinder
Chapter 3: The ANSYS Multi-field (TM) Solver - MFS Single-Code Coupling

This chapter describes the ANSYS Multi-field solver- single code (MFS), available for a large class of coupled analysis problems. An automated tool for solving sequentially coupled field problems, the ANSYS Multi-field solver supersedes the physics file-based procedure and provides a robust, accurate, and easy to use tool for solving sequentially coupled physics problems. It is built on the premise that each physics is created as a field with an independent solid model and mesh. You can identify surfaces or volumes for coupled load transfer, and then use a set of multi-field solver commands to configure the problem and define the solution sequencing. The solver automatically transfers coupled loads across dissimilar meshes. The MFS solver is applicable to static, harmonic, and transient analysis, depending on the physics requirements. Any number of fields can be solved in a sequential (staggered) manner.

The ANSYS Multi-field solver is one of two versions of the multi-field solver (see Chapter 4, “Multi-field Analysis Using Code Coupling” for a description of the other version, the MFX solver). The MFS solver is the basic multi-field solver used if the simulation involves small models that have all physics field contained within a single program (e.g., ANSYS). The MFS solver uses iterative coupling where each physics is solved sequentially and each matrix equation solved separately. The solver iterates between each physics field until the loads transferred across physics interfaces converge.

The ANSYS Multi-field solver has the following main features:

- Each physics is created as a "field" with an independent model and mesh.
- Each field is defined by a group of element types.
- Load transfer regions are identified by surfaces and/or volumes.
- Load vector coupling occurs between fields.
- Each field may have different analysis types.
- Each field may have different solvers and analysis options.
- Each field may have a different mesh discretization.
- Surface load transfer can occur across fields.
- Volumetric load transfer can occur across fields.
- Non-structural elements can be automatically morphed.
- Independent results files are created for each field.

The ANSYS Multi-field solver can solve a large class of coupled field problems. Typical applications include the following:

- Thermal stress
- Joule heating
- Induction heating and stirring
- Fluid-structure interaction
- Electromagnetic-structural interaction
- Electrostatic-structural interaction
- RF heating
• Current conduction-magnetostatics

The following ANSYS Multi-field solver (MFS) topics are available:
3.1. The ANSYS Multi-field solver and Solution Algorithm
3.2. ANSYS Multi-field solver Solution Procedure
3.3. Sample Thermal-Stress Analysis of a Thick-walled Cylinder (Batch or Command Method)
3.4. Sample Electrostatic Actuated Beam Analysis (Batch or Command Method)
3.5. Sample Induction-Heating Analysis of a Circular Billet

3.1. The ANSYS Multi-field solver and Solution Algorithm

The ANSYS Multi-field solver is available in the ANSYS Multiphysics product. It provides you with the ability to solve coupled-field problems such as the following:

• MEMS Actuation (electrostatic/structural without fluid coupling)
• Electric Machines (magneto/thermal/structural coupling)
• Joule Heating (thermal/electric/structural coupling)
• Induction Heating (harmonic electromagnetic/thermal coupling)
• Induction Stirring (harmonic electromagnetic/thermal/fluid coupling)
• RF Heating (high-frequency electromagnetic/thermal/structural coupling)
• Thermal/Stress Analysis (thermal/structural coupling)
• Fluid Solid Interaction Analysis (fluid/structural coupling)

The following ANSYS Multi-field solver algorithm topics are available:
3.1.1. Load Transfer
3.1.2. Mapping
3.1.3. Coupled Field Loads
3.1.4. Elements Supported
3.1.5. Solution Algorithm

3.1.1. Load Transfer

Load transfer is the process by which one field transmits mesh-based quantities to another field. The transfers occur from a surface to a surface or from a volume to a volume. Electrostatic Actuated Beam Analysis is an example of a surface load transfer problem. In that problem, forces are transmitted from the electrostatic field to the structural field and displacements are transmitted from the structural domain to the electrostatic field. Thermal-Stress Analysis of a Thick-walled Cylinder and Induction-heating Analysis of a Circular Billet are examples of volumetric load transfer problems. In the thick-walled cylinder problem, temperatures are transferred from the thermal field to the structural field. In the circular billet problem, heat generation is transferred from the magnetic field to the thermal field and temperatures are transferred from the thermal field to the magnetic field.

The ANSYS Multi-field solver automatically transfers coupled loads across dissimilar meshes. Two interpolation methods are available for a load transfer: profile preserving and globally conservative. In a profile preserving interpolation, each node on the receiver side maps onto an element on the sender side ($a_i$). The transfer variable is then interpolated at $a_i$. The transfer value is $T_i = \phi (\alpha_i)$. Thus, all nodes on the receiver side query the sender side.
Figure 3.1 Profile Preserving Interpolation

In a globally conservative interpolation, each node X on the sender maps onto an element on the receiver side. Thus, the transfer variable on the sender is split into two quantities that are added to the receiver nodes. As shown in the following figure, the force at node 4 splits into forces at nodes 3' and 4'.

Figure 3.2 Globally Conservative Interpolation

Some important points to remember about the interpolation methods are:

- For a profile preserving interpolation, the forces and heat rate will not balance on this interface. For a globally conservative interpolation, total force and total heat rate will balance on this interface. However, locally the distributions might not agree.
It makes physical sense to conserve quantities like heat flux and force at the surface interfaces. Similarly, heat generation should be conserved at volumetric interfaces. However, it does not make physical sense to conserve displacements or temperatures on an integral basis. However, displacement and temperature profiles should be adequately captured across interfaces.

As shown in the following figures, for a profile preserving interpolation, you should have a coarse mesh on the sending side and a fine mesh on the receiver side, rather than the converse. When the coarse mesh is on the sending side, the receiver adequately captures the normal heat flux profile. On the receiver side, a fine mesh ensures a sufficient number of nodes. When the coarse mesh is on the receiver side, the receiver does not adequately capture the normal heat flux profile due to an insufficient number of nodes on the receiver side.
As shown in the following figures, for a globally conservative interpolation it is better to have a fine mesh on the sending side and a coarse mesh on the receiver side than the converse. When the fine mesh is on the sending side, the receiver adequately captures the forces. When the fine mesh is on the receiver side, the load distribution on the receiver might not be captured, even though the total force on the receiver is equal to the total force on the sender.
The above two points hold true if either the sender or receiver mesh is made of higher order elements. Exercise care if you wish to produce a node-to-node mapping from higher order elements to lower order elements. For example, as shown in the following figure, a globally conservative load transfer across an interface that has the same number of elements on both sides will not produce the correct profile if the receiver is higher order.

To get the right profile, you need to double the number of sending lower order elements as shown in the following figure. Also note you cannot drop mid-side nodes at a surface or volume interface.
You can specify a globally conservative or a profile preserving interpolation method for forces, heat flux, and heat generation. Displacement and temperature transfers are always profile preserving.

### 3.1.2. Mapping

In order to transfer loads across a dissimilar mesh interface, the nodes of one mesh must be mapped to the local coordinates of an element in the other mesh. The MFS solution algorithm must perform two mappings for every surface to surface and volume to volume interface. For example, in a fluid-solid interaction problem, fluid nodes must be mapped to the solid elements to transfer displacements. Likewise, solid nodes must be mapped to the fluid elements to transfer stresses.

#### 3.1.2.1. Mapping Algorithms

There are two mapping algorithms available: global and bucket search.

**Global Method**

As the name implies, the node in question loops over all the existing elements of the other mesh and tries to locate an element that it can be mapped to. Most nodes find a unique element and are mapped easily. However, occasionally a node is mapped to two or more elements. This occurs when a finite nonzero gap/penetration exists.
between the two meshes. The element that minimizes the distance is then selected. In the following figure, node \( N_1 \) is found in elements \( e_1 \) and \( e_2 \), so it is mapped to the element which minimizes the gap distance (\( e_1 \) because \( d_1 < d_2 \)).

**Figure 3.12 Node Mapped to Minimize Gap**

![Gap between two meshes](image)

Sometimes a node does not map to any element. This occurs when the interface edges are not aligned. In the following figure, node \( N_1 \) does not map to any element, so it is mapped to the closest node (\( N'_1 \)).

**Figure 3.13 Node Mapped to Closest Node**

![Node mapping to closest node](image)

The global method has a complexity of \( O(n \times m) \) where \( n \) is the number of nodes mapped onto \( m \) elements. If \( n \) and \( m \) are of the same order, the time required to compute the mapping grows quadratically and leads to computational inefficiency, especially for large models.

*Note — The same issues exist for 3-D models involving surface-to-surface mapping. They are also encountered for volumetric mapping in 2-D and 3-D models.*

**Bucket Search Method**


For a given node, the bucket search method restricts the elements over which it loops. This is accomplished as follows:

1. All elements are distributed in Cartesian boxes (also referred to as buckets).
2. The node in question is then located in a box.
3. The global method is used for the node in question, but the elements are restricted to that box only.

For example, in the following figure, elements $e_1$, $e_2$, and $e_3$ are in box 1, elements $e_3$ and $e_4$ are in box 2, and $e_4$, $e_5$, and $e_6$ are in box 3. Node $N_1$ searches only over the elements in box 3.

**Figure 3.14 Node in Box 3 with Three Elements**

When the node in question is in a box with elements, the mapping is identical to global mapping.

While this procedure appears straightforward, it is more complex when the node in question is in an empty box as shown in the following figure. This can occur when there are gap/penetration issues or the interface edges are misaligned.

**Figure 3.15 Nine boxes and Node in Empty Box**

The mapping is then different than global mapping. The mapping procedure requires locating the nearest boxes that have elements and choosing only one box for element looping.

The bucket search method has a complexity of $O(n)$ where $n$ is the number of nodes to be mapped onto $m$ elements. However, to achieve this increased efficiency, buckets must be created and the $m$ elements must be placed in them, at an additional computational expense.

*Note — This same mapping process is used for 3-D models involving surface-to-surface mapping and 2-D and 3-D models involving volumetric mapping.*

### 3.1.2.2. Mapping Diagnostics

You can use the **MFTOL** command (**Main Menu**> **Preprocessor**> **Multi-field Set Up**> **MFS-Single Code**> **Setup**> **Global**) to turn normal distance checking on for surface mapping and to set a normal distance limit from a node to an element surface. The normal distance limit defaults to $1.0e^{-6}$. 
As shown in the following figure, in surface mapping, improperly mapped nodes include nodes that exceed the normal distance limit specified (figure a) and nodes that are on misaligned surfaces (figure b). In volumetric mapping, improperly mapped nodes are nodes out of the target domain (figure c).

**Figure 3.16 ImproperlyMapped Nodes**

The mapping tool creates components to graphically display nodes that are improperly mapped. Component names for surface mapping are MFSU_interface number_field number_label_field number (for example, MFSU_1_1_TEMP_2). Component names for volumetric mapping are MFVO_interface number_field number_label_field number (for example, MFVO_2_1_HGEN_2).

### 3.1.2.3. Mapping Operations

You can use the MFMAP command (**Main Menu** > **Preprocessor** > **Multi-field Set Up** > **MFS-Single Code** > **Interface** > **Mapping**) to calculate, save, resume, or delete mapping data. By saving mapping data to a file and using resume, you might be able to significantly reduce computing time during a restart or another solve. If you wish to resume a mapping file, be sure to first delete any existing mapping data in memory. You can also use this command to check your mapping without performing a solution. See the **ANSYS Commands Reference** for more information about this command.

### 3.1.3. Coupled Field Loads

The following tables show the loads that the ANSYS Multi-field solver can transfer in a coupled physics analysis.

#### Table 3.1 Load Transfer Between Fields

<table>
<thead>
<tr>
<th>Field</th>
<th>Structural</th>
<th>Thermal</th>
<th>Electric</th>
<th>Magnetic</th>
<th>Fluid</th>
</tr>
</thead>
<tbody>
<tr>
<td>Structural</td>
<td>1</td>
<td>2</td>
<td>3</td>
<td>4</td>
<td></td>
</tr>
<tr>
<td>Thermal</td>
<td>5</td>
<td>6</td>
<td>7</td>
<td></td>
<td></td>
</tr>
<tr>
<td>Electric</td>
<td>8</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
</tbody>
</table>

1. Structural - Thermal Coupling
### Table 3.1: The ANSYS Multi-field solver and Solution Algorithm

<table>
<thead>
<tr>
<th>Volumetric Load Transfer</th>
<th>Structural</th>
<th>Thermal</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Displacements</td>
<td>Temperature</td>
</tr>
<tr>
<td>Receive</td>
<td>Temperature</td>
<td>Displacements</td>
</tr>
</tbody>
</table>

2. **Electrostatic - Structural Coupling**

<table>
<thead>
<tr>
<th>Surface Load Transfer</th>
<th>Structural</th>
<th>Electrostatic</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Displacements</td>
<td>Forces</td>
</tr>
<tr>
<td>Receive</td>
<td>Forces</td>
<td>Displacements</td>
</tr>
</tbody>
</table>

3. **Structural - Magnetic Coupling**

<table>
<thead>
<tr>
<th>Surface or Volumetric Load Transfer</th>
<th>Structural</th>
<th>Magnetic</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Displacements</td>
<td>Forces</td>
</tr>
<tr>
<td>Receive</td>
<td>Forces</td>
<td>Displacements</td>
</tr>
</tbody>
</table>

4. **Structural - Fluid Coupling**

<table>
<thead>
<tr>
<th>Surface Load Transfer</th>
<th>Structural</th>
<th>Fluid</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Displacements</td>
<td>Forces</td>
</tr>
<tr>
<td>Receive</td>
<td>Forces</td>
<td>Displacements</td>
</tr>
</tbody>
</table>

5. **Thermal - Electric Coupling**

<table>
<thead>
<tr>
<th>Volumetric Load Transfer</th>
<th>Thermal</th>
<th>Electric</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Temperature</td>
<td>Heat Generation</td>
</tr>
<tr>
<td>Receive</td>
<td>Heat Generation</td>
<td>Temperature</td>
</tr>
</tbody>
</table>

6. **Thermal - Magnetic Coupling**

<table>
<thead>
<tr>
<th>Volumetric Load Transfer</th>
<th>Thermal</th>
<th>Magnetic</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Temperature</td>
<td>Heat Generation</td>
</tr>
<tr>
<td>Receive</td>
<td>Heat Generation</td>
<td>Temperature</td>
</tr>
</tbody>
</table>

7. **Thermal - Fluid Coupling**

<table>
<thead>
<tr>
<th>Surface Load Transfer</th>
<th>Thermal</th>
<th>Fluid</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Temperature/Heat Flux</td>
<td>Temperature/Heat Flux</td>
</tr>
<tr>
<td>Receive</td>
<td>Heat Flux/ Temperature</td>
<td>Heat Flux/ Temperature</td>
</tr>
</tbody>
</table>

8. **Magnetic - Fluid Coupling**

<table>
<thead>
<tr>
<th>Volumetric Load Transfer</th>
<th>Magnetic</th>
<th>Fluid</th>
</tr>
</thead>
<tbody>
<tr>
<td>Send</td>
<td>Forces</td>
<td>—</td>
</tr>
<tr>
<td>Receive</td>
<td>—</td>
<td>Forces</td>
</tr>
</tbody>
</table>
3.1.4. Elements Supported

The ANSYS Multi-field solver supports the elements shown in the following tables. These elements support the SF family of commands (SF, SFA, SFE, or SFL) for surface load transfer (field surface interface: FSIN flag) and the BFE command for volumetric load transfer (field volume interface: FVIN flag) during an analysis. You need to flag these elements at the surface (FSIN) and volume (FVIN) interface for load transfer to other fields during the analysis. Other elements types can be used in any of the field analyses, but they will not participate in load transfer.

Table 3.2 Structural and Thermal Elements

<table>
<thead>
<tr>
<th>Structural Elements</th>
</tr>
</thead>
<tbody>
<tr>
<td>PLANE</td>
</tr>
<tr>
<td>PLANE2</td>
</tr>
<tr>
<td>PLANE42</td>
</tr>
<tr>
<td>PLANE82</td>
</tr>
<tr>
<td>PLANE182</td>
</tr>
<tr>
<td>PLANE183</td>
</tr>
</tbody>
</table>

<table>
<thead>
<tr>
<th>Thermal Elements</th>
</tr>
</thead>
<tbody>
<tr>
<td>PLANE</td>
</tr>
<tr>
<td>PLANE35</td>
</tr>
<tr>
<td>PLANE55</td>
</tr>
<tr>
<td>PLANE77</td>
</tr>
</tbody>
</table>

Table 3.3 Electromagnetic, Fluid, and Coupled-Field Elements

<table>
<thead>
<tr>
<th>Electromagnetic Elements</th>
</tr>
</thead>
<tbody>
<tr>
<td>PLANE</td>
</tr>
<tr>
<td>PLANES3</td>
</tr>
<tr>
<td>PLANES121</td>
</tr>
<tr>
<td>PLANES230</td>
</tr>
<tr>
<td>SOLID122</td>
</tr>
<tr>
<td>SOLID123</td>
</tr>
<tr>
<td>SOLID231</td>
</tr>
<tr>
<td>SOLID232</td>
</tr>
</tbody>
</table>

<table>
<thead>
<tr>
<th>Fluid Elements</th>
</tr>
</thead>
<tbody>
<tr>
<td>PLANE</td>
</tr>
<tr>
<td>FLUID141 [1]</td>
</tr>
</tbody>
</table>

<table>
<thead>
<tr>
<th>Coupled-Field Elements</th>
</tr>
</thead>
<tbody>
<tr>
<td>PLANE</td>
</tr>
<tr>
<td>PLANES13</td>
</tr>
<tr>
<td>PLANES67</td>
</tr>
<tr>
<td>PLANES223</td>
</tr>
</tbody>
</table>
1. You can use the FLOTRAN remeshing capability in a fluid-solid interaction analysis. See Section 7.3: Remeshing in the *ANSYS Fluids Analysis Guide* for additional information.

### 3.1.5. Solution Algorithm

The solution algorithm for the ANSYS Multi-field solver is shown in the following figure. The `MFANALYSIS` command activates a solution. The solution loop consists of three loops: field loop, stagger loop, and time loop. The ANSYS Multi-field solver supports transient, static, and harmonic analysis of fields inside the field loop.

**Figure 3.17 ANSYS Multi-field solver Algorithm**

- **Time**
  - **Stagger**
    - **Field**
      - Field Analysis
        - Element Types
        - Solution Options
        - Loads Send/Receive
  - **End Field**
  - **End Stagger**
  - **End Time**

The time loop corresponds to the time step loop of the MFS problem and is set with the `MFTIME` command. A constant time step size may be set with the `MFDTIME` command. For a static analysis the time loop refers to the load step for each field analysis. For harmonic analysis the time loop refers to a harmonic solution within the time step. For a transient analysis, the time step represents the actual time transient end time and time step. Load transfer between fields occur at the time loop time steps.

Within each time loop is the stagger loop. The stagger loop allows for implicit coupling of the fields in the MFS solution. Within each step in the time loop, the field solutions are repeated in the stagger loop until convergence. The number of iterations within the stagger loop is determined by the convergence of the loads transfer between fields or the maximum number of stagger iterations specified by the `MFITER` command.

Within each stagger loop is the field loop. The field loop contains the analysis of each field solution. The field Loop is set up like any single ANSYS analysis. Each field can be set up by grouping a set of element types using the `MFELEM` command. Solution options for each field are set using the `MFCOMMAND` command. Surface and volumetric load transfer between fields is specified using the `MFSURFACE` and `MFVOLUME` commands, respectively. Fields can share a dissimilar mesh across the interface and load transfer from a field occurs after the solution of the respective field. Load transfer to a particular field occurs before solution of the field. Morphing (`MORPH` command) of a non-structural field mesh occurs prior to the field solution. The morphing is based on displacements of a previous structural field solution.
3.2. ANSYS Multi-field solver Solution Procedure

The procedure for doing an MFS solution analysis consist of the following steps:

3.2.1. Set up Field Models
3.2.2. Flag Field Interface Conditions
3.2.3. Set up Field Solutions
3.2.4. Obtain the solution
3.2.5. Postprocess the Results

3.2.1. Set up Field Models

To perform an MFS analysis, you first create the field models in ANSYS. These models may be set up completely independently. The only criteria is that they share the same geometry (duplicate solid models). They may be created in a single ANSYS database, or in separate databases and imported (MFIMPORT command) to build a model. Each model consists of everything required to solve a particular field, including mesh, boundary conditions, analysis options, output options, etc. For information on how to set up a field analysis, refer to the ANSYS Fluids Analysis Guide, the ANSYS Structural Analysis Guide, the ANSYS Thermal Analysis Guide, and the ANSYS Low-Frequency Electromagnetic Analysis Guide.

If you will be generating radiosity surface elements (RSURF), you must first mesh the different regions, and then generate the radiosity surface elements on each meshed region individually. Use RSURF,,ETNUM to assign a separate element type number to each region. This procedure allow you to identify the individual regions later in the multi-field analysis. Also, include the radiosity surface element types in the field definition (MFELEM).

3.2.2. Flag Field Interface Conditions

The next step is to flag field surface and volume interfaces for load transfer. Flagged surfaces sharing a common surface interface number will exchange surface load data; flagged volumes sharing a common volume interface number will exchange volume load data.

For surface load transfer across fields, use the SF family of commands (SF, SFA, SFE, or SFL) and the FSIN surface load label. Apply the field surface interface flag twice, once for each field surface where load transfer occurs. When issuing the SF, SFA, SFE, or SFL commands with the FSIN flag, apply the same interface number for both field interfaces. Load transfer occurs between fields with the same interface number. Also maintain unique interface numbers for load transfer across each pair of field surface interface, as these interface numbers are used in the MFSURFACE command for specifying the surface load transfer options.

For volumetric load transfer, use the BFE command and the FVIN volume load label. Apply the field volume interface flag twice: once for each field volume where load transfer occurs. When issuing the BFE command with the FVIN flag, apply the same interface number for both field interfaces where load transfer occurs. Load transfer occurs between fields with the same interface number. Also maintain unique interface numbers for load transfer across each pair of field volume interface, as these interface numbers are used in the MFVOLUME command for specifying the volume load transfer options.

3.2.3. Set up Field Solutions

The procedure for setting up the field solutions consists of the following main steps:

- Define fields and capture field solutions.
- Set up interface load transfers.
- Set up global field solution.
Set up stagger solution.
Set up time and frequency controls.
Set up morphing (if necessary).
Clear or list settings.

### 3.2.3.1. Define Fields and Capture Field Solutions

The following table lists the steps to define the fields and capture the field solutions.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
</table>
| Define a field by grouping element types, add more element types to the field, or import a defined field into a current analysis. | MFELEM | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Define> Define  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Define> Define |
| | MFEM | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Define> Add elems  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Define> Add elems |
| | MFIMPORT | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Import |
| Specify a file name for each field. | MFFNAME | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Define> Define  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Define> Define |
| Capture solution options for each field. | MFCMMAND | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Capture  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Capture |
| Delete all solution options before setting options for a new field. | MFCLEAR | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Clear  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Clear |

Use the **MFELEM** command to define the fields for analysis. Use the **MFEM** command to add more element types to the field if it has more than 10 element types defined. It groups element types into different fields with a specified field number for the ANSYS Multi-field solver. Elements grouped into a field for analysis should belong to a single physics. More precisely, a single physics represents an ANSYS model using a single set of elements solving that physics. For instance, a coupled-field element type set for piezoelectric analysis will solve simultaneously electric and structural analysis within a single field loop. You may wish to couple this field model to a thermal field model to include thermal effects. The number of element types in a field must not be changed between restarts.

In addition to defining fields from models created in one ANSYS session, you can import fields defined in another ANSYS session and saved via a CDB file (**CDWRITE** command). Use the **MFIMPORT** command to import any number of new fields into a current analysis. With this option, you can prepare field models independently and then combine them to perform an MFS solution.
Note — If you are importing a FLOTRAN fluid field along with other fields, the FLOTRAN fluid field must be imported last to ensure that the fluid region will have a material number of 1.

The FLOTRAN element must be in counterclockwise order for a 2-D FSI analysis (for Figure 141.1: “FLUID141 Geometry”, I, J, K, L order) and it must be in positive volume order for a 3-D FSI analysis (for Figure 142.1: “FLUID142 Geometry”, I, J, K, L, M, N, O order). If the element order is not proper, you will need to recreate the mesh to reverse it.

The import option makes use of the NUMOFF command capability to offset the current database numbering of entities to allow the model on the CDB file to be imported. Fields defined using the MFELEM or MFEM commands are updated based on the renumbered element type numbers. If no field is defined before the MFIMPORT command is issued, the program will automatically group the existing element types into a field (MFELEM or MFEM) and write any solution options to a command file (MFCMMAND). The field on the CDB file is assigned the field number that you specify, and it is read into the database accordingly. Exercise caution when using the MFIMPORT option since the NUMOFF command capability has some limitations.

Use the MFFNAME command to define file names for each field used in the MFS analysis. The field file name is used for all files during solution of the specified field. The field file name defaults to field"n" where n is the field number.

MFS analysis allows different solution options to be specified for each field analysis. Use the MFCMMAND command to capture solution options for each field number. The solution options are written to a file, and read when the field is solved. Issue the MFCLEAR, SOLU command to clear all existing solution options before setting options for a new field. The MFCLEAR, SOLU command sets all solutions options to defaults values in ANSYS. Specify solution options for each field analysis by issuing the ANSYS solution commands for analysis options, nonlinear options, load step options, etc. The solution options are written to a file that you specify for the given field number. The command file name defaults to field"n".cmd where n is the field number.

Note — If you need to model morphing, you must set that up before you issue the MFCMMAND command. For information on morphing, see Section 3.2.3.6: Set up Morphing (if necessary).

MFS analyses allow either stepped or ramped loading, but not both. The KBC command is globally used for all fields by the ANSYS Multi-field solver and therefore is not written to the field-specific command files. This restriction is due to the consistent load transfer issue between the fields. If the KBC command is not issued before the SOLVE command, ramped loading (KBC,0) is used. If the KBC command is issued more than once, the loading type specified by the last command is used.

3.2.3.2. Set up Interface Load Transfers

The following table lists the steps to set up interface load transfers.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Define surface load transfers.</td>
<td>MFSURFACE</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Interface&gt; Surface</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Interface&gt; Surface</td>
</tr>
<tr>
<td>Define volume load transfers.</td>
<td>MFVOLUME</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Interface&gt; Volume</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Interface&gt; Volume</td>
</tr>
</tbody>
</table>
MFS analysis allows load transfer across flagged surface and volume interfaces. Use the **MFSURFACE** command to specify a surface load transfer across a field interface. Specify the variable being transferred, the send and receive field numbers, and the field surface interface number specified by the SF family of commands (SF, SFA, SFE, or SFL) and the FSIN surface load label. Use the **MFVOLUME** command to specify volume load transfer across a field interface. Specify the variable being transferred, the send and receive field numbers, and the field surface interface number specified by the BFE command and the FVIN volume load label.

### 3.2.3.3. Set up Global Field Solution

The following table lists the steps to set up the global field solution.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
</table>
| Turn the ANSYS Multi-field solver analysis on. | **MFANALYSIS** | Main Menu> Preprocessor> Multi-field Set Up> Select method  
Main Menu> Solution> Multi-field Set Up> Select method |
| Specify a globally conservative or profile preserving load transfer interpolation. | **MFINTER** | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Setup> Global  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Setup> Global |
| Specify a search option for load transfer interpolation. | **MFBUCKET** | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Setup> Global  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Setup> Global |
| Specify the field analysis order. | **MFORDER** | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Setup> Order  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Setup> Order |
| Define external fields (if necessary). | **MFEXTER** | Main Menu> Preprocessor> Multi-field Set Up> MFS-Single Code> Setup> External  
Main Menu> Solution> Multi-field Set Up> MFS-Single Code> Setup> External |

Use the **MFANALYSIS** command to activate an MFS analysis. **MFANALYSIS**, OFF deactivates an analysis (OFF is the default).

Use the **MFINTER** command to specify a globally conservative or profile preserving interpolation for the load transfer across the field interface. Globally conservative or profile preserving interpolation applies to forces, heat flux, and heat generation transferred across a field interface. Profile preserving interpolation transfers forces, heat flux, and heat generation across field interfaces as flux quantities, and globally conservative interpolation transfers these variables as forces and heat rates. The interpolation defaults to profile preserving.

A bucket search is the default option. This option partitions the interface into small cells (buckets) for more efficient interface data mapping. You can specify a scaling factor for the search algorithm (default is 50%). The number of buckets is equal to the scaling factor times the number of elements at the search interface. Use the **MFBUCKET** command if you want to switch to a global search.

Use the **MFORDER** command to specify the solution order for the defined fields. The **MFORDER** command specifies the order of the field solutions from the first field solution to the last field solution of the MFS analysis.
You can define an external field (MFEXTER) that predefines loads and exists only to transfer those loads to another field. It requires fully specified loads and does not perform a solution during an MFS analysis. It only transfers a load to another field. The external field should be set up in the following fashion:

- If transferring displacements or temperature from an external field, specify the required displacements or temperature using the D command, on the external field mesh. Also specify the variable label to be transferred using MFSURFACE or MFVOLUME for surface or volumetric load transfer, respectively.
- If transferring forces or heat flux from an external field, specify the forces or heat rates using the F command on the external mesh. Constrain the complete field mesh with a trivial displacement or temperature.

The External field capability allows an easy mechanism for transferring results from an external software code that can support writing a CDB file consisting of nodes, elements, and loads.

Use the MFEXTER command to define external fields during a analysis. Specify the loads to be transferred on the external field and use MFSURFACE or MFVOLUME to specify the load to be transferred to other fields across a field interface.

### 3.2.3.4. Set up Stagger Solution

The following table lists the steps to set up the stagger solution.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Set the maximum number of stagger iterations.</td>
<td>MFITER</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Stagger&gt; Iterations</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Stagger&gt; Iterations</td>
</tr>
<tr>
<td>Specify convergence values.</td>
<td>MFCONV</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Stagger&gt; Convergence</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Stagger&gt; Convergence</td>
</tr>
<tr>
<td>Specify relaxation values.</td>
<td>MFRELAX</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Stagger&gt; Relaxation</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Stagger&gt; Relaxation</td>
</tr>
</tbody>
</table>

Use MFITER to set the maximum number of stagger iterations between the fields for an MFS analysis. At the end of each stagger loop, the coupling algorithm checks the convergence of the quantities transferred across the interface. The analysis proceeds to the next time step if the interface quantities have converged. The stagger solution continues until the maximum number of stagger iterations has been reached or convergence occurs. The default is 10 stagger iterations.

Use MFCONV to specify the convergence norm for the quantities transferred at the surface and volume interface across each field interface. The default is 0.001. The interpolation algorithm (globally conservative or profile preserving) determines the quantities transferred across the field interface.

Use MFRELAX to specify the relaxation values for the load transfer variables across the surface and volume field interface. If you are using a single stagger iteration for each time step of the MFS analysis, use a relaxation value of 1.0 for all quantities. The default relaxation value is 0.5.
### 3.2.3.5. Set up Time and Frequency Controls

The following table lists the steps to set up the time and frequency controls.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Set end time for MFS analysis.</td>
<td>MFTIME</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Set time step increment for MFS analysis.</td>
<td>MFDTIME</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Set time step increment for each field analysis.</td>
<td>DELTIM</td>
<td>Main Menu&gt; Preprocessor&gt; Loads&gt; Load Step Opts&gt; Time/Frequency&gt; Time - Time Step</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Load Step Opts&gt; Time/Frequency&gt; Time - Time Step</td>
</tr>
<tr>
<td></td>
<td>FLDATA4</td>
<td>Main Menu&gt; Preprocessor&gt; FLOTRAN Set Up&gt; Transient Ctrl&gt; Time Integration Meth</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; FLOTRAN Set Up&gt; Transient Ctrl&gt; Time Integration Meth</td>
</tr>
<tr>
<td>Specify a restart (if necessary).</td>
<td>MFRSTART</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Time Ctrl</td>
</tr>
<tr>
<td>Specify a calculation frequency for a field (if necessary).</td>
<td>MFCALC</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Frequency</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Frequency</td>
</tr>
<tr>
<td>Specify the output frequency for MFS analysis.</td>
<td>MFOOUTPUT</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Frequency</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Frequency</td>
</tr>
</tbody>
</table>

Use the **MFTIME** command to specify the end time of your MFS analysis. The end time should be a multiple of the time step increment. Use the **MFDTIME** command to specify an initial time step, minimum time step, and maximum time step size. The solution only supports constant time stepping. The time step increment and end time default to 1.

You must also specify the time step increment for each field analysis. Use **DELTIM** for a structural, thermal and electromagnetic analysis and **FLDATA4**, **TIME**, **STEP**, **Value**, for a fluid analysis. Auto time-stepping (**AUTOTS**) may be used within a field analysis as well. The time step increment for each field analyses should be less than or equal to the time step increment for the MFS analysis. The analysis sub-cycles over each field analyses so that load transfer across the field interface occurs at time increments specified by **MFDTIME**. The **MFCMMAND** command captures the time step size for each field analysis.
You can restart the MFS analysis from either the last time step or the last converged solution in the results file.

Note — The ANSYS Multi-field solver does not support ramped loads (KBC,0) with restarts (MFRSTART). Instead, use tabular boundary conditions with stepped loads (KBC,1).

Use MFCALC to set the calculation frequency for a given field within the analysis. The field solution for any given field can be obtained at every time step or every Nth time step. The calculation frequency option only applies to a field using a harmonic or static analysis. This option is useful, for example, in skipping the harmonic field solution (and load transfer updating) during a time step when the field quantities transferred are not varying significantly over the specified time increment (MFDTIME).

Use MFOUTPUT to set the output frequency for results from your analysis with respect to the time step (MFDTIME). You can write output at every time step or every Nth time step. The output frequency applies to each field results file.

### 3.2.3.6. Set up Morphing (if necessary)

In an MFS analysis, the deflection of a structure may affect the solution of a surrounding non-structural field. A good example is electrostatic-structural interaction in MEMS structures where the structural deformation alters the electrostatic field which in turn alters the electrostatic forces and resulting deformation. To model this type of behavior, the field mesh surrounding a structure must be updated to coincide with the deflection of the structure. The process of updating the field mesh is called morphing. The structural field sends displacements to the non-structural field using the MFSURFACE command for a defined surface interface. The ANSYS Multi-field solver makes use of the MORPH command to invoke morphing within a given field model.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Turn morphing on (if necessary)</td>
<td>MORPH</td>
<td>Main Menu&gt; Preprocessor&gt; Loads&gt; Load Step Options&gt; Other&gt; Element Morphing</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Loads&gt; Load Step Options&gt; Other&gt; Element Morphing</td>
</tr>
</tbody>
</table>

The MORPH command is applicable to any non-structural field analysis. The command activates the UX, UY, and UZ degrees of freedom for non-structural elements so that boundary conditions may be placed on the field mesh to constrain the movement of the non-structural mesh during morphing. Morphing of a field mesh occurs during
the non-structural field stagger prior to the field solution using displacements transferred at the surface interface between the structural field and the non-structural field.

The procedure for preparing a non-structural mesh for morphing is as follows. You must complete these steps before you issue the MFCMMAND command.

1. Create the non-structural model and mesh.
2. Issue the morphing command (MORPH,ON) to turn on non-structural field morphing, except for any FLOTRAN fluid field morphing. For FLOTRAN fluid fields, use the KEYOPT, ITYPE, 4,1 command to set up morphing.

If morphing is activated during the solution, it will remain active until deactivated. Changing field solutions will not necessarily deactivate morphing. To avoid unwanted morphing in structural fields, MORPH,OFF should be issued before issuing MFCMMAND. If morphing is ON for any field, the recommended practice is to explicitly define morphing (either ON or OFF) for all fields.

3. Apply appropriate structural boundary condition constraints to the boundary of the non-structural mesh (typically, you set normal components of displacement to zero).

Morphed fields must be in the global Cartesian system (CSYS = 0).

Note — The MORPH option is different than DAMORPH, DVMORPH, or DEMORPH. DAMORPH, DVMORPH, and DEMORPH are not compatible with the ANSYS Multi-field solver.

The ANSYS Multi-field solver currently does not provide a remeshing capability for electromagnetic physics fields. The DAMORPH, DVMORPH, and DEMORPH commands do allow remeshing. These command are used by the ESSOLV command macro. If remeshing is needed, use the ESSOLV macro; otherwise, for an analysis needing mesh morphing without remeshing, the ANSYS Multi-field solver is typically a more robust solution method.

### 3.2.3.7. Clear or List Settings

To delete or list MFS analysis settings, use the commands shown in the following table.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Delete MFS analysis settings.</td>
<td>MFCLEAR</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Clear</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Clear</td>
</tr>
<tr>
<td>List MFS analysis settings.</td>
<td>MFLIST</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Status</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFS-Single Code&gt; Status</td>
</tr>
</tbody>
</table>

### 3.2.4. Obtain the solution

To obtain the solution or restart the MFS analysis from either the last time step or the last converged solution in the results file, use the commands shown in the following table.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Obtain the solution.</td>
<td>SOLVE</td>
<td>Main Menu&gt; Solution&gt; Current LS</td>
</tr>
</tbody>
</table>
3.2.5. Postprocess the Results

To postprocess an analysis, the database must be available and the appropriate results file selected. To select the appropriate results file, use the FILE command in POST1 or POST26. The results file names are based on the settings used on the MFFNAME command. You can review results using standard ANSYS POST1 and POST26 commands. Be sure to select the appropriate field element types for the results file selected before you postprocess the results (ESEL). MFS analyses do not support simultaneous postprocessing of the field results.

When postprocessing results in the time-history (POST26) postprocessor, if the structural analysis is performed first and a FLOTRAN analysis is performed second (MFOR), you must issue the STORE,NEW command immediately after the FILE, fname, rst command in order to have both the FLOTRAN and structural degrees of freedom properly activated for postprocessing.

For information on postprocessing, refer to An Overview of Postprocessing in the ANSYS Basic Analysis Guide.

Note — The multi-field solver is restricted to single-frame restarts. As a result, you cannot get correct contact forces from the results file when you have an active database. To get the correct forces, use the last database file (which was saved right after the SOLVE command) only, or read the results file only without the database (see below).

To use the database only:

```
/solu
solve
save
fini
/clear
resume,file, db
/post1
esel,s,ename,,174
nsle
fsum,,cont
```

To read the results file without the database:

```
/clear
/post1
file, struct, rst
set, last
esel,s,ename,,174
nsle
fsum,,cont
```

The displacements of non-structural elements are mesh (or grid) displacements to avoid mesh distortion but have no physical meaning except at the interface between the structural field and the non-structural field.
3.3. Sample Thermal-Stress Analysis of a Thick-walled Cylinder (Batch or Command Method)

3.3.1. Problem Description

A thick-walled cylinder is maintained at a temperature $T_i$ on the inner surface and $T_o$ on the outer surface. The temperature distribution in the cylinder and the axial and hoop stresses at the inner surface are determined. See ANSYS Verification Manual problem VM32 Thermal Stresses in a Long Cylinder for a similar problem.

A quarter-cylinder model is chosen to demonstrate the thermal-stress analysis using a dissimilar mesh between the thermal and structural models. SOLID87 elements model the thermal response while SOLID95 elements model the structural response.

The thermal model is constructed first. Temperature constraints are applied to the inner and outer surface. The structural model is constructed next. Constraints are applied to simulate symmetry boundary conditions. In the z-direction, one face is constrained while the other face has the UZ degree of freedom for the nodes coupled to simulate an infinitely long cylinder.

A volumetric load transfer flag is set for all the elements since the mesh for the thermal and structural models completely overlap.

In the solution phase, the model is set up to use the ANSYS Multi-field solver (MFANALYSIS). The thermal analysis is identified as field #1, assigning the thermal element type to that field (MFELEM). In a similar fashion, the structural analysis is identified as field #2 with the structural element type assigned to that field. Since this is a static analysis, the time is set to 1.0 (MFITER) with a single time increment (MFDTIME). Relaxation of the transferred load quantities is set to 0.5 (MFRELAX).

Field file names are assigned which will be used in the naming of the results files (MFFNAME). A volumetric load transfer is defined which will send temperatures from the thermal field to the structural field (MFVOLUME). Analysis options are set for the thermal solution and written to a command file (MFCMMAND). Similarly, analysis options are set for the structural solution and written to a command file. The solution is then performed.

The following figure illustrates the thermal and structural mesh.
3.3.2. Results

The following figure illustrates the thermal solution and the axial stress.
Figure 3.20 Temperature Profile and Axial Stress
The analytic solution for both the hoop and axial stress is 420.24 at the inner cylinder wall. The ANSYS results are shown in the following table.

**Table 3.4 Hoop and Axial Stress Variation**

<table>
<thead>
<tr>
<th>Stress Component</th>
<th>Min Value</th>
<th>Max Value</th>
</tr>
</thead>
<tbody>
<tr>
<td>Hoop Stress</td>
<td>418.3</td>
<td>418.9</td>
</tr>
<tr>
<td>Axial Stress</td>
<td>421.5</td>
<td>421.7</td>
</tr>
</tbody>
</table>

### 3.3.3. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment.

```
/batch, list
/TITLE, Thermal stress analysis of a long thick cylinder
/com, Reference: Verification Manual Problem VM32
/com,****************** Characteristics *******************************
/com,
/com, Thermal Element: SOLID87
/com, Structural Element: SOLID95
/com,
/com,******************** Expected results *******************************
/com,
/com, At inner radius: Axial and hoop stress = 420.42
/com,
```
Section 3.3: Sample Thermal-Stress Analysis of a Thick-walled Cylinder (Batch or Command Method)

```plaintext
/com,******************************************************************
/com,
ir=.1875                   ! Cylinder inner radius
or=.625                    ! Cylinder outer radius
theta=90                   ! Angle for partial cylinder model
h=.5
/prep7
! Thermal model
et,1,87                  ! Thermal element type
mp,kxx,1,1.3                ! Conductivity
cylind,ir,or,0,h,0,theta   ! Build thermal model
esiz,,6
vmesh,all                  ! Free tetrahedral mesh
csys,1
nsel,s,loc,x,ir
d,all,temp,-1              ! Set inner wall temperature
nsel,s,loc,x,or
d,all,temp,0                ! Set outer wall temperature
allsel,all
! Structure Model
et,2,95                  ! Structural element type
mp,ex,2,30E6                ! Structural properties
mp,alpx,2,1.435E-5
mp,nuxy,2,.3

cylind,ir,or,0,h,0,theta   ! Build structural model
esiz,,9
vatt,2,1,2
vmesh,all                  ! Mapped brick mesh
csys,0
esel,s,type,,2
nsle
nsel,r,loc,z
nsle
esel,r,loc,z,h
egp,1,uz,all
nsle
esel,r,loc,y
d,all,uy,0
nsle
esel,r,loc,x
d,all,ux,0
allsel,all
bfe,all,fvin,,1            ! Volumetric Flag for load transfer
finish
/solu
mfan,on                    ! Activate MFS analysis
mfel,1,1                   ! Field #1: Thermal
mfel,2,2                   ! Field #2: Structure
mfor,1,2                   ! Field order (thermal, structure)
mfti,1                     ! Time at end of analysis
mfdt,1                     ! One field loop within a stagger
mfit,5                     ! Max 5 stagger loops
mfre,all,0.5               ! Field transfer relaxation parameter
mffn,1,therm1              ! Field #1 filename
mffn,2,struc2              ! Field #2 filename
mfvo,1,1,temp,2            ! Volumetric load transfer (temp to structure)
antyp,stat
eqslv,iccg
mfcm,1                      ! Write thermal analysis options
antyp,static
mfcvm,1
mfcvm,2                      ! Write structure analysis options
solve
finish
/post1
file,therm1,rth             ! Thermal results file
set,last
esel,s,type,,1              ! Select thermal elements
```

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3–27
3.4. Sample Electrostatic Actuated Beam Analysis (Batch or Command Method)

3.4.1. Problem Description

A clamped beam for an RF MEMS switch device is modeled to compute the center deflection for an applied voltage. Forces generated by the electrostatic field will bend the beam towards a ground plane.

SOLID45 brick elements model the beam. A half-width model is constructed with symmetry boundary conditions placed at the plane of symmetry. The beam is clamped at both ends. A surface interface flag (FSIN) is placed on the bottom beam surface. NLGEOM is set for geometric nonlinearities (large deflection and stress stiffening).

SOLID123 tetrahedral elements model the air underneath the beam. Fringing effects are ignored for simplicity. (Fringing effects may be considered by extending the model for the electrostatic domain beyond the boundary of the beam.) A surface interface flag (FSIN) is placed at the top of the electrostatic domain coincident with the structural beam mesh. The morphing command is activated (MORPH, on) to enable the application of structural boundary conditions at the periphery of the electrostatic domain. This is done to prepare the electrostatic domain for mesh movement (morphing) during the coupled field solution. Voltages are applied at the top and bottom surface of the electrostatic domain. A plot of the structural and electrostatic elements is shown in Figure 3. Note that the meshes are dissimilar at the interface between the domains.

The structure model is defined as field number 1; the electrostatic model is defined as field number 2 (MFELEM). Analysis options are defined for both field solutions and written to files (MFCMMAND). A static solution is defined for both fields. For the electrostatic model, 120 volts is applied with a ramped boundary condition (KBC) at 10 volt solution intervals (DELTIM). The field order for the solution is set to solve the electrostatic field first, followed by the structural field (MFORDER). The “time” is set to 120 (MFTIME) to correspond to the voltage level (for convenience) with ANSYS Multi-field solver solutions requested at 10 volt intervals (MFDTIME). Up to 20 stagger iterations are defined (MFITER). Globally conservative load transfer is prescribed (MFINTER). Forces are transferred from the electrostatic domain to the structural domain (MFSURFACE). Displacements are transferred from the structural domain to the electrostatic domain for use in morphing of the electrostatic mesh (MFSURFACE).
3.4.2. Results

The total number of cumulative iterations for 12 converged ramped solutions was 153 (due to geometric nonlinearity in the structural field). Results for each field are stored in separate results files. Each field is postprocessed individually.
Figure 3.22  Beam Displacement for 120 Volt Load
Figure 3.23 Electrostatic Field
3.4.3. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment.

```
/batch,list
/title, Electrostatic clamped beam analysis
/com, ANSYS Multi-field solver
/com, globally conservative Load transfer
/com, Structure: SOLID45 brick elements
/com, Electrostatic: SOLID123 tetrahedral elements
/com, uMKSV units

bl=150                  ! beam length, um
bh=2                    ! beam height, um
bw=4                    ! beam width, um
gap=2                   ! gap, um

/prep7

! Structural model
et,1,45                 ! 8-node bricks
mp,ex,1,169e3           ! kg/(um)(s)^2
mp,nuxy,1,0.066         ! kg/(um)^2
mp,dens,1,2.329e-15     ! kg/(um)^3
```
block, 0, bl, 0, bh, 0, bw  ! structural volume
asl
lsla
lssel, r, loc, x, bl/2
lesize, all, /, 20, /, 1  ! 20 bricks along bl
lsla
lssel, r, loc, y, bh/2
lesize, all, /, 2, /, 1  ! 2 bricks along bh
lsla
lssel, r, loc, z, bw/2
lesize, all, /, 1, /, 1  ! 1 brick along bw
vatt, 1, 1
vmesh, all
alls
asel, s, loc, y, bh/2  ! clamp beam ends
asel, r, loc, z, bw/2
nsla, s, 1
da, all, ux
da, all, uy
da, all, uz
alls
asel, s, loc, y, bh/2  ! symmetry plane
asel, r, loc, z, 0
nsla, s, 1
da, all, uz
alls
nsel, s, loc, y, 0
sf, all, fsin, 1  ! Define Surface interface

! Electrostatics model
et, 2, 123
emunit, EPZRO, 8.854e-6  ! pF/um
mp, perx, 2, 1
morph, on  ! enable morph bc's
block, 0, bl, -gap, 0, 0, bw  ! electrostatic volume
vsel, s, volu, /, 2
smrtsz, 2
mshape, 1, 3D
mshkey, 0
vatt, 2, 2
vmesh, all
asl, s
asel, r, loc, x, 0
da, all, ux, 0  ! Apply structural morphing constraints
asl, s
asel, r, loc, x, bl
da, all, ux, 0
asl, s
asel, r, loc, z, 0
da, all, uz, 0
asl, s
asel, r, loc, z, bw
da, all, uz, 0
asl, s
asel, r, loc, y, -gap
da, all, uy, 0
asl, s
asel, r, loc, y, 0
nsla, s, 1
sf, all, fsin, 1  ! Define Surface interface
da, all, volt, 120  ! Apply voltage
nsel, s, loc, y, -gap
da, all, volt, 0  ! Apply ground potential
allsel, all
fini
/solu
mfan, on  ! Activate ANSYS Multi-field solver analysis
mfel, 1, 1  ! structure field
mfel, 2, 2  ! electrostatic field
mfor, 2, 1  ! Order for field solution
mfc0, all, 1.0e-5  ! Convergence settings
3.5. Sample Induction-Heating Analysis of a Circular Billet

3.5.1. Problem Description

This example illustrates a transient induction heating problem. The problem demonstrates the use of the ANSYS Multi-field solver using an electromagnetic harmonic analysis stagger and a time-transient heat transfer stagger. A similar problem using APDL command macros to perform the solution staggering is shown in Example Induction-heating Analysis Using Physics Environments. Please refer to it for a description of the problem. A summary is given below along with details on using the ANSYS Multi-field solver for this application.

A simplified geometry considers only a finite length strip of the long billet, essentially reducing the problem to a one-dimensional study as shown in the following figure.
Figure 3.25 Axisymmetric 1-D Slice of the Induction Heating Domain

PLANE53 elements model the electromagnetic field solution. Boundary conditions and loads are shown in the following figure.

Figure 3.26 Nominal Electromagnetic Physics Boundary Conditions

Current Density: \( JSZ = 15 \times 10^6 \text{ A/m}^2 \)

PLANE55 elements model the thermal problem. Radiation at the outer billet surface is modeled using the Radiosity Solver, assuming radiation to the open domain at 25 degrees Centigrade. Boundary conditions are shown in the following figure.

Figure 3.27 Nominal Thermal Physics Boundary Conditions

\( \frac{\partial T}{\partial Y} = 0 \)  
Radiation (\( T = 25^\circ C \))

\( \frac{\partial T}{\partial X} = 0 \)

\( \frac{\partial T}{\partial Y} = 0 \)

The following figure illustrates the ANSYS Multi-field solver solution sequencing for this problem.
The electromagnetic analysis is defined as field number 1 (MFELEM) with element types 1 and 2. The thermal analysis is defined as field number 2 (MFELEM) with element type 4. The stagger order is field 1 followed by field 2 (MFORDER). The final solution time is defined (MFTIME) as well as the stagger loop time increment (MFDTIME). The electromagnetic analysis options for the harmonic analysis are defined for field 1 and written to a file (MFCMMAND). The thermal analysis options for a transient analysis are defined for field 2 and written to a file (MFCMMAND). The thermal analysis includes auto time-stepping within the stagger time loop. Volumetric load transfer is defined for two variables. First, the heat generation is passed from field 1 (electromagnetic) to field 2 (thermal). Second, the temperatures from the thermal solution (field 2) are passed to the electromagnetic field (field 1) so that temperature dependent properties may be evaluated. Heat generation loads and temperatures are passed at the synchronization time points defined at the stagger loop time increments (MFDTIME).

### 3.5.2. Results

The following figures show the temperature of the surface and the centerline over time and a temperature profile after 3 seconds.
Figure 3.29 Centerline and Surface Temperature
3.5.3. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment.

```
/batch,list
/title, Induction heating of a solid cylinder billet
/prep7
/shpp,off
/com,
/com,

row=.015                   ! outer radius of workpiece
ric=.0175                  ! inner radius of coil
roc=.0200                  ! outer radius of coil
ro=.05                     ! outer radius of model
t=.001                     ! model thickness

freq=150000                ! frequency (Hz.)
pi=4*atan(1)               ! pi
cond=.392e7                ! maximum conductivity
muzero=4e-7*pi             ! free-space permeability
mur=200                    ! maximum relative permeability

skind=sqrt(1/(pi*freq*cond*muzero*mur))  ! skin depth
ftime=3                    ! final time

tinc=.05                   ! time increment for harmonic analysis
```
time=0                     ! initialize time
delt=.01                   ! maximum delta time step

! Electromagnetic model
et,1,53,,1                ! PLANE53, axisymmetric, AZ dof
et,2,53,,1

emunit,mks                 ! set magnetic units
mp,murx,1,1                ! air relative permeability
mp,murx,3,1                ! coil relative permeability
mptemp,1,25.5,160,291.5,477.6,635,698    ! temps for relative permeability
mptemp,7,709,720,3,742,761,1000
mpdata,murx,2,1,200,190,182,161,135,104    ! steel relative permeability
mpdata,murx,2,7,84,35,17,1,1
mptemp
mptemp,1,0,125,250,375,500,625    ! temps for resistivity
mptemp,7,750,875,1000
mpdata,rsvx,2,1,184e-6,.272e-6,.384e-6,.512e-6,.656e-6,.824e-6
mpdata,rsvx,2,7,1.032e-6,1.152e-6,1.2e-6    ! steel resistivity
mptemp
mptemp,1,0,730,930,1000    ! temps for conductivity
mptemp,7,765,765.001,927
mpdata,enth,2,1,60.64,29.5,28,28    ! temps for enthalpy
mpdata,enth,2,7,3.548547e9,3.548556e9,4.3520e9
mpdata,enth,2,1,0,91609056,453285756,1.2748e9,2.2519e9,3.3396e9
mpdata,enth,2,7,3.548556e9,4.3520e9
mp,emis,2,.68              ! emissivity
rectng,0,row,0,t           ! billet
rectng,row,ric,0,t         ! coil
rectng,roc,ro,0,t          ! outer air
aglue,all

numcmp,area
kssel,s,loc,x,row          ! select keypoints at outer radius of workpiece
kesize,all,skind/2         ! set meshing size to 1/2 skin depth
kssel,s,loc,x,0            ! select keypoints at center
kesize,all,40*skind        ! set meshing size
lssel,s,loc,y,t/2          ! select vertical lines
lesize,all,,1              ! set 1 division through thickness
lssel,all

asel,s,area,,1
aatt,2,1,1                ! set attributes for billet region
asel,s,area,,3
aatt,3,1,2                ! set attributes for coil region
asel,s,area,,2,4,2
aatt,1,1,2                ! set attributes for air region
asel,all
mshape,0,2d
mshk,1                    ! mesh billet area
lssel,s,loc,y,0
lssel,a,loc,y,t
lssel,u,loc,x,row/2
lesize,all,,.001
lssel,all
amesh,all                ! mesh remaining areas
nssel,s,loc,x
d,all,az,0                ! apply flux-normal b.c.
nssel,all
esel,s,mat,,3
bfe,all,js,,15e6          ! apply current density to coil
alls

! Thermal model
et,4,55,,1                ! PLANE55 thermal element, axisymmetric
agen,2,1,,,,,,,,,1
aatt,2,1,4
ksel,s,loc,x,row           ! select keypoints at outer radius of workpiece
kesize,all,skind/2         ! set meshing size to 1/2 skin depth
kesize,all,0             ! select keypoints at center
kesize,all,40*skind       ! set meshing size
isel,s,loc,y,t/2          ! select vertical lines
lesize,all,1             ! set 1 division through thickness
isel,all
mshape,0,2d
msk,1
amesh,5
asel,,,,5
alssel,below,area
nsel,r,loc,x,row
sf,all,rdsf,0.68,1          ! Radiation
alls
spctemp,1,25              ! Space temperature
v2dopt,1
radopt,0.01
ste,5.67e-8               ! Stefan-Boltzman constant
esel,s,mat,,2             ! select billet material
bfe,all,fvin,,1           ! define volumetric interface
finish
/solu
mfan,on                    ! Activate ANSYS Multi-field solver analysis
mfel,1,1,2                 ! Field #1 ET;s,  Emag
mfel,2,4                   ! Field #2 ET's, Thermal
mfor,1,2                   ! Field solution order
mfpi,ftime                 ! Final time
mfdt,tinc                  ! Stagger time increment
mfco,all,1e-3              ! Convergence criteria
antyp,harm                  ! Emag analysis options
harfrq,150000
outres,all,all
munif,100
mfcm,1                      ! Write Emag analysis options
mfclear,solu                ! Clear analysis options
antype,trans                ! Thermal analysis options
toffst,273
munif,100                   ! initial uniform temperature
kbc,1                       ! step loads
tntopt,full
autos,on
deltim,.01,.005,.01,on      ! auto time-stepping
mfcm,2                      ! time step control
mfvo,1,1,hgen,2             ! Write Thermal analysis options
mfvo,1,2,temp,1             ! Transfer hgen from Emag to Thermal
solve
save
finish
/post26
file,field2,rth
esel,s,type,,4
nsle,s
nsel,r,loc,x,row            ! get node at outer radius
nsel,r,loc,y,0              ! get node at centerline
nsel,r,loc,x,0
nsel,r,loc,y,0
*get,nor,node,,num,min
nsol,2,nor,temp,outerR       ! Outer radius
nsol,3,nir,temp,inner       ! Inner radius (centerline)
plvar,2,3
prvar,2,3
finish
/post1
file,field2,rth

Chapter 3: The ANSYS Multi-field (TM) Solver - MFS Single-Code Coupling

ANSYS Coupled-Field Analysis Guide. ANSYS Release 10.0. 002184. © SAS IP, Inc.
set, last                   ! Solution at 3 seconds
esel,s,type,,4             ! select thermal elements
plns,temp                  ! plot temperature
finish
Chapter 4: Multi-field Analysis Using Code Coupling

This chapter describes the ANSYS Multi-field solver - multiple code coupling (MFX), available for a large class of coupled analysis problems. The MFX solver is one of two versions of the ANSYS Multi-field solver. See Chapter 3, “The ANSYS Multi-field (TM) Solver - MFS Single-Code Coupling” for a description of the other version, the MFS solver. The MFX solver is used for simulations with physics fields distributed between more than one code running on one or more machines (e.g., between ANSYS Multiphysics or Mechanical and ANSYS CFX). Thus, this solver can accommodate more physically complex and larger models than the MFS version.

In the MFX solver, a “field solver” is each running instance of the different codes. These field solvers are coupled using stagger iterations. During each iteration, every field solver collects loads from the other field solvers and proceeds to solve its own physics fields. Iterations continue until all physical field solutions and loads converge. The coupling between field solvers running on potentially different machines is accomplished using a client/server based communication protocol over standard internet sockets. No third party software is required, allowing for maximum flexibility and extensibility.

The MFX solver is primarily intended for fluid - structure interaction (FSI) analyses (including conjugate heat transfer), where the structural part of the analysis is solved using ANSYS Multiphysics (or Mechanical) and the fluid part using ANSYS CFX-FCS. Typical applications include:

- Biomedical applications (i.e., drug delivery pumps, intravenous catheters, elastic artery modeling for stent design)
- Aerospace applications (i.e., airfoil flutter, turbine engines)
- Automotive applications (i.e., under hood cooling, HVAC heating/cooling, heat exchangers)
- Fluid handling applications (i.e., valves, fuel injection components, pressure regulators)
- Civil engineering applications (i.e., wind and fluid loading of structures)
- Electronics cooling

If you are not familiar with the ANSYS Multi-field solver, read the ANSYS Multi-field solver discussion before using MFX. You must also be familiar with CFX.

This chapter describes how to do a fluid-structure interaction analysis using ANSYS Multiphysics (or Mechanical) and ANSYS CFX-FCS products. You must be using ANSYS 10.0 or later and CFX 10.0 or later.

To use the MFX solver, your analysis must meet the following requirements:

- You must be running on one of the following platforms: HP, SGI, Linux 32-bit, Linux AMD Opteron 64-bit, Linux EM64T 64-bit, or Windows 32-bit.
- The analysis must be three-dimensional.
- The ANSYS model must be single-field and the elements involved in load transfer must be 3-D with either structural or thermal DOFs.
- Only surface loads are transferred. Valid surface loads are displacement, temperature, force and force density, heat flow, and heat flux.
- Only two field solvers, one ANSYS and one CFX, can be coupled. A given analysis can have only one coupling between two field solvers, but it can have multiple load transfers.
• The ANSYS field cannot be distributed, but the CFX field can use CFX's parallel processing capabilities. A CFX field being solved using parallel processing is still considered a single field solver.
• The analysis must be a batch run.
• Only the singleframe restart is supported.
• ANSYS allows static and transient analyses; however, CFX allows only transient analyses.

The following terms are used throughout this chapter:

**Field Solver**
A field solver refers to a specific instance of an ANSYS or CFX solver execution that is defined by the respective input file(s) referenced when starting the solver (through the launcher or from the command line). The field solver names that are referenced in several MFX commands must be consistent with the names that will be used when starting the coupled simulation.

**Client**
The client code actively requests information from the server code.

**Server**
The server code works passively, providing information to the client code, and will never send information that has not been requested.

**Master**
The master performs the coupling setup (e.g., reads all MFX commands, collects the interface meshes from the slave code, does the mapping) and sends instructions (time and stagger loop controls) to the slave executable. In MFX, the ANSYS code is always the master. During the simulation process, the master will act as both a client and a server.

**Slave**
The slave code receives the coupling control information from the master code and sends the interface meshes to master. It receives instructions (time and stagger loop controls) during simulation. In MFX, the CFX code is always the slave. During the simulation process, the slave will act as both a client and a server.

**Simultaneous**
Field solvers can be grouped together for simultaneous execution during each stagger iteration. When grouped this way, all field solvers collect their respective loads from the other field solvers, and then all proceed to solve their physics fields simultaneously.

**Sequential**
Field solvers that are not grouped together for simultaneous execution are executed sequentially during each stagger iteration. In this case, each field solver collects its respective loads from the other field solvers and proceeds to solve its physics fields.

The following MFX topics are available:
4.1. How MFX Works
4.2. MFX Solution Procedure
4.3. Starting and Stopping an MFX Analysis
4.4. Example Simulation of a Piezoelectric Actuated Micro-Pump

**4.1. How MFX Works**

The ANSYS code functions as the master: it reads all Multi-field commands, collects the interface meshes from the CFX code, does the mapping, and communicates time and stagger loop controls to the CFX code. The mapping generated by ANSYS is used to interpolate loads between dissimilar meshes on either side of the coupling interface. Each field solver advances through a sequence of multi-field time steps and stagger (coupling)
iterations within each time step. During every stagger iteration, each field solver collects the loads that it requires from the other field solvers and then solves its physics fields.

You can run the CFX field solver using CFX’s parallel processing capabilities to run large-scale parallel CFD jobs on either the same or a different platform as ANSYS.

### 4.1.1. Synchronization Points and Load Transfer

Using MFX, data are transferred throughout the fluid-solid interaction analysis. The points at which data are transferred are called synchronization points. Data can be sent or received only at a synchronization point, as shown in Figure 4.1: “MFX Method Data Communication”.

**Figure 4.1 MFX Method Data Communication**

<table>
<thead>
<tr>
<th>Actions</th>
<th>Master (ANSYS code)</th>
<th>Slave (CFX code)</th>
</tr>
</thead>
<tbody>
<tr>
<td>initialize</td>
<td>create socket</td>
<td>connect to master</td>
</tr>
<tr>
<td>SP1</td>
<td>GET code info</td>
<td>Serve code info</td>
</tr>
<tr>
<td></td>
<td>Serve global control info</td>
<td>GET global control info</td>
</tr>
<tr>
<td>SP2</td>
<td>GET interface meshes</td>
<td>Serve interface meshes</td>
</tr>
<tr>
<td></td>
<td>DO MAPPING</td>
<td>Serve initial and restart loads</td>
</tr>
<tr>
<td></td>
<td>GET initial load and restart loads</td>
<td></td>
</tr>
<tr>
<td>SP3</td>
<td>Serve time step begin</td>
<td>GET</td>
</tr>
<tr>
<td></td>
<td>stagger begin</td>
<td></td>
</tr>
<tr>
<td>SP4</td>
<td>load transfer</td>
<td>load transfer</td>
</tr>
<tr>
<td></td>
<td>DO SOLVE</td>
<td></td>
</tr>
<tr>
<td></td>
<td>load transfer</td>
<td></td>
</tr>
<tr>
<td>SP5</td>
<td>GET slave local convergence</td>
<td>Serve local convergence</td>
</tr>
<tr>
<td></td>
<td>Serve global convergence</td>
<td>GET global convergence</td>
</tr>
<tr>
<td></td>
<td>Serve time convergence</td>
<td>GET time convergence</td>
</tr>
</tbody>
</table>

At each synchronization point, the ANSYS and CFX codes shift their client privileges sequentially: the client code queries the server code to get information and the server code serves data until it receives a command to get client privileges or is asked to go to the next synchronization point. For the load transfer, each code gets all interface boundary conditions from the other code before solving. Depending on whether the field solvers are being solved simultaneously (in the same group defined by the **MFPSIMUL** command) or sequentially, the codes will serve loads before or after solving, respectively.

### 4.1.2. Elements and Load Types Supported

MFX supports all ANSYS 3-D elements, including structural (solid and shell), thermal, electromagnetic, and coupled-field elements. These elements support the SF family of commands (**SF**, **SFA**, or **SFE**) for surface load transfer (field surface interface: FSIN flag) during an analysis. You need to flag these elements at the surface (FSIN) for load transfer to other fields during the analysis. Other element types can be used in the analysis, but they will not participate in load transfer and should not be located on the interface. MFX supports only mechanical and thermal load transfer between fields.
4.1.3. Solution Process

The solution process for MFX is shown in the figure below. The ANSYS code acts as the master and reads all MFX commands, does the mapping, and serves the time step and stagger loop controls to the CFX slave. The MFANALYSIS command activates a master multi-field solution. The solution loop consists of two loops: the multi-field time loop and the multi-field stagger loop.

The ANSYS field solver supports transient and static analyses. CFX supports only a transient analysis. If you want a static solution, running a static analysis on ANSYS will help CFX to reach a solution more quickly.

**Figure 4.2 ANSYS Multi-field solver Process**

ANSYS Master

CFX Slave

Do Mapping

Time Loop

Stagger Loop

ANSYS Solver

Time Controls

Stagger Controls (ANSYS to CFX)

Load Transfers

Stagger Controls (bidirectional)

End Stagger Loop

End Time Loop

CFX Solver

Time Loop

Stagger Loop

Time Controls

End Stagger Loop

End Time Loop

The time loop corresponds to the time step loop of the multi-field analysis, set with the MFTIME command. Use the MFDTIME command to specify time step size.

Within each time step is the stagger loop. The stagger loop allows for implicit coupling of the fields in the MFX solution. The number of stagger iterations applies to each time step in the MFX analysis. Within each step in the time step loop, the field solutions are repeated in the stagger loop until convergence. The number of iterations executed within the stagger loop is determined by the convergence of the loads transfer between fields or the maximum number of stagger iterations specified by the MFITER command. For a transient analysis performed in CFX, the stagger iteration contains many CFX coefficient iterations, which loop until convergence or until the maximum number of coefficient iterations is reached. Load transfers between fields occur at each stagger loop. Global convergence is checked after the load transfer. If global convergence of the load transfer is not achieved, another stagger loop is performed.

Use the MFLCOMM command to specify surface load transfer between field solvers. The meshes used in the individual field solvers can be dissimilar across the interface. Before solving a given field, all necessary loads are collected from the other field solver. Loads are transferred either before or after solution of the field solver, depending on whether the field solver groups are set to solve sequentially or simultaneously.

4.2. MFX Solution Procedure

The procedure for an MFX solution consists of the following steps:

4.2.1. Set Up ANSYS and CFX Models
4.2.2. Flag Field Interface Conditions
4.2.1. Set Up ANSYS and CFX Models

To perform an MFX analysis, you must first create the ANSYS and CFX models (e.g., mesh, boundary conditions, analysis options, output options, etc.) For information on creating the ANSYS model, refer to the ANSYS Structural Analysis Guide, the ANSYS Thermal Analysis Guide, and the other ANSYS analysis guides. For information on creating the CFX model, see the discussion on Solver Modeling in the CFX documentation.

4.2.2. Flag Field Interface Conditions

The next step is to flag field surfaces for load transfer. ANSYS surfaces are flagged by interface number and CFX surfaces are flagged by interface name. The ANSYS interface is defined by the SF family of commands (SF, SFA, or SFE) with the FSIN surface load label. The CFX interface is defined as a boundary condition with an option set to ANSYS Multi-field for relevant quantities. Load transfer occurs between ANSYS and CFX field solvers on the flagged interface(s). Use the MFLCOMM command to specify the surface load transfer. You can specify multiple interface numbers or interface names in an MFX run by issuing multiple MFLCOMM commands.

4.2.3. Set Up Master Input

The procedure for setting up the master input consists of the following main steps:

4.2.3.1. Set Up Global MFX Controls
4.2.3.2. Set Up Interface Load Transfer
4.2.3.3. Set Up Time Controls
4.2.3.4. Set Up Mapping Operations
4.2.3.5. Set Up Stagger Solution
4.2.3.6. List or Clear Settings

4.2.3.1. Set Up Global MFX Controls

The following table lists the steps to set up the global MFX controls. You must specify the solution order (MF-SORDER); there is no default setting.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command/Option</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Turn on the ANSYS Multi-field solver.</td>
<td>MFANALYSIS</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; Select method</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; Select method</td>
</tr>
<tr>
<td>Set up the field solver groups for sequential or simultaneous solution.</td>
<td>MFPSIMUL</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Solution Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Solution Ctrl</td>
</tr>
<tr>
<td>Specify the solution sequence.</td>
<td>MFSORDER</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Solution Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Solution Ctrl</td>
</tr>
</tbody>
</table>
Use the **MFANALYSIS** command to activate an ANSYS Multi-field solver analysis. Issue **MFANALYSIS,OFF** to deactivate the analysis (OFF is the default).

Use the **MFPSIMUL** command to specify groups of field solvers that you want to process simultaneously. For example, one group with both the ANSYS and CFX field solvers yields the following behavior: ANSYS requests its loads from CFX, CFX requests its loads from ANSYS, then both solvers execute simultaneously (see Figure 4.3: “ANSYS and CFX Fields Solved Simultaneously”). Two **MFPSIMUL** commands, each containing one field solver, are required to process and solve field solvers sequentially (see Figure 4.4: “ANSYS and CFX Fields Solved Sequentially, ANSYS First”).

Use the **MFSORDER** command to specify the order in which to process the groups of field solvers identified in the **MFPSIMUL** command(s).

*Note* — If you use the GUI to create the ANSYS input file, ANSYS will automatically use ANSYS as the ANSYS field solver name and CFX as the CFX field solver name. In this case, when running MFX from the launcher, you must then use ANSYS and CFX (uppercase) as the field solver names.

If you are working interactively, ANSYS generates the **MFPSIMUL** and **MFSORDER** as shown in Figure 4.3: “ANSYS and CFX Fields Solved Simultaneously” and Figure 4.4: “ANSYS and CFX Fields Solved Sequentially, ANSYS First”, depending on whether you selected a simultaneous or sequential solution. You can specify the global relaxation factor (see **MFRELAX,ALL,VALUE**) at this point.

- To set up a simultaneous solution, use the **MFPSIMUL** command once, with one group name and both field solver names. Again, use the **MFSORDER** command to specify the solution order.

**Figure 4.3  ANSYS and CFX Fields Solved Simultaneously**

MFPS,group1,ANSYS,CFX  
MFSO,group1

- To set up a sequential solution, use the **MFPSIMUL** command to set up two groups, each time with just one field. Then use the **MFSORDER** command to specify the solution order.
The **MFPSIMUL** and **MFSORDER** commands are used to optimize computing resource usage according to the nature of the physical coupling between the fields being solved.

Weakly coupled fields can often be solved simultaneously (i.e., via a single **MFPSIMUL** command). In this case, the overall simulation time may decrease because no field solver must wait for results/loads from another field solver. If the fields are too strongly coupled, however, this approach may also destabilize the solution process because less recent results/loads are applied in each field solver. Strongly coupled fields should be solved sequentially (i.e., via multiple **MFPSIMUL** commands), which ensures that the most recent results/loads from one field solver are applied to the other. Multiple stagger iterations are often required to obtain a fully implicit solution by the end of each multi-field time step (see **MFITER**).

In most simulations, the physical processes in one field solver will drive those in another field solver. In many FSI cases, for example, the forces generated by the fluid fields lead to strains in the solid field. In such cases, the **MFSORDER** command should specify that the ‘driver’ field solver (the fluid field solver in this case) be solved first.

### 4.2.3.2. Set Up Interface Load Transfer

MFX allows load transfer across flagged surfaces. Use the **MFLCOMM** command to set up the load transfer between the ANSYS and CFX codes. You must specify the load transfer information; there is no default setting.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command/Option</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Set up the load communication.</td>
<td>MFLCOMM</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Load Transfer</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Load Transfer</td>
</tr>
</tbody>
</table>

Specify the names of field solvers sending and receiving quantities, the surface name or number, and the variable being transferred. The interpolation option -- Global Conservative or Profile Preserving (nonconservative) -- determines how loads are transferred across the field. Use **Global Conservative** (CONS) for heat flow and forces and use **Profile Preserving** (NONC) for heat flux and force density. As noted in the **MFLCOMM** command description, the interpolation type needs to be consistent with which data are transferred for the CFX code.
If you are working interactively, you can choose two pre-defined combinations, Mechanical or Thermal, or you can choose a Custom option. If you choose the Mechanical load type, then the Total Force Density and Mesh Displacement data (corresponding to the ANSYS FORC and DISP labels, respectively) are transferred. If you choose the Thermal load type, then the Temperature and Wall Heat Flux data (corresponding to the ANSYS TEMP and HFLU labels, respectively) are transferred. If you choose Custom, you can select any valid combination of label and option as described in the MFLCOMM command description. If you leave the CFX Region Name as “default,” CFX will automatically find the corresponding multi-field interface name.

Note — You can specify multiple interface numbers or interface names (up to 50) in an MFX run by issuing multiple MFLCOMM commands.

### 4.2.3.3. Set Up Time Controls

The following table lists the steps to set up the time controls.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Set end time for ANSYS Multi-field solver analysis.</td>
<td>MFTIME</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX &gt;Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX &gt;Time Ctrl</td>
</tr>
<tr>
<td>Set time step size for ANSYS Multi-field solver analysis.</td>
<td>MFDTIME</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX &gt;Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX &gt;Time Ctrl</td>
</tr>
<tr>
<td>Restart the ANSYS Multi-field solver analysis (if necessary).</td>
<td>MFRSTART</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX &gt;Time Ctrl</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX &gt;Time Ctrl</td>
</tr>
</tbody>
</table>

Use the MFTIME command to specify the end time of your MFX analysis. Use the MFDTIME command to specify an initial time step, minimum time step, maximum time step size, and time step carryover key (for restarts). The time step size and end time default to 1. If either DTMIN or DTMAX is not equal to DTIME on the MFDTIME command, auto time-stepping is turned on for the multi-field time loop. ANSYS will automatically adjust the next multi-field time step size to occur between DTMIN and DTMAX, based on the status of the current convergence, the number of target stagger iterations (specified by MFITER), and the actual number of iterations needed to reach convergence at the current time step.

You must also specify the time step increment for each ANSYS field analysis. Auto time-stepping (AUTOTS) may be used within a field analysis. The time step increment for each ANSYS field analysis should be less than or equal to the time step increment for the overall analysis. The analysis allows sub-cycling over the ANSYS field, but load transfer across the field interface only occurs at multi-field time increments. CFX does not support sub-cycling, so the internal time step size for CFX should be the same as the multi-field time increments.

Note — MFX does not support the multiframe restart available in a structural analysis. Only singleframe restart is allowed. To restart a run you must exit the previous run. New input files must be created for both ANSYS (see Singleframe Restart) and CFX to restart a run.

The ANSYS Multi-field solver does not support ramped loads (KBC,0) with restarts (MFRSTART). Instead, use tabular boundary conditions with stepped loads (KBC,1).
### 4.2.3.4. Set Up Mapping Operations

<table>
<thead>
<tr>
<th>Step</th>
<th>Command/Option</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Specify a search option for load transfer interpolation.</td>
<td>MFBUCKET</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Mapping</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Mapping</td>
</tr>
<tr>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Activate normal distance checking.</td>
<td>MFTOL</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Mapping</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Mapping</td>
</tr>
</tbody>
</table>

You must use the bucket search method, which is set by default. If you turn off the bucket search option, you will get error messages when you solve. This option partitions the interface into small cells (buckets) for more efficient interface data mapping. You can specify a scaling factor for the search (the default is 50%). The number of buckets is equal to the scaling factor multiplied by the number of elements at the search interface.

For a dissimilar mesh interface, the nodes of one mesh are mapped to the local coordinates of an element in the other mesh. When normal distance checking (MFTOL) is activated, the mapping tool checks the normal distance from the node to the nearest element. The node is considered improperly mapped if the normal distance exceeds the tolerance value. The mapping tool creates a component to graphically display the improperly mapped nodes. See Section 3.1.2.2: Mapping Diagnostics in the *ANSYS Coupled-Field Analysis Guide* for more information.

### 4.2.3.5. Set Up Stagger Solution

The following table lists the steps to set up the stagger solution.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Set the maximum number of stagger iterations.</td>
<td>MFITER</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Iterations</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Iterations</td>
</tr>
<tr>
<td>Specify convergence values.</td>
<td>MFCONV</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Convergence</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; Advanced Set Up&gt; Convergence</td>
</tr>
</tbody>
</table>
Use the \texttt{MFITER} command to set the maximum number of stagger iterations between the field solvers for each multi-field time step. At the end of each stagger iteration, the ANSYS master checks the convergence of the quantities transferred across the interface and the fields within each field solver. The analysis proceeds to the next time step if the interface quantities have converged. The stagger solution continues until the maximum number of stagger iterations has been reached or convergence occurs. The default is 10 stagger iterations. You can also specify a minimum stagger iteration (\texttt{MFITER,MINITER}) and a target stagger iteration (the desired number of stagger iterations) (\texttt{MFITER,TARGET}) for auto time stepping in MFX.

Use the \texttt{MFCONV} command to specify the convergence norm for the quantities transferred across each field at the interface. The default is 0.001.

\textit{Note} — Iteration controls and convergence criteria must also be set for the fields being solved in each of the coupled field solvers. Iteration controls are important for controlling the efficiency and stability of the coupled analysis. Convergence criteria are important for controlling the accuracy of the solutions provided by each field solver. General recommendations are summarized as:

- Set the convergence criteria to obtain the desired level of solution accuracy.
- Set the maximum stagger iterations to a value that is large enough to satisfy the convergence criteria during each multi-field time step.
- Limit the work (e.g., iterations) done during the execution of each field solver to maintain a tighter coupling and promote efficiency and stability.

Use the \texttt{MFRELAX} command to specify the relaxation values for the load transfer variables across the surface. The default relaxation value is 0.75. \texttt{Option = RELX} will usually give you a more stable and smooth load transfer and is suitable for strongly coupled problems (such as FSI problems). \texttt{Option = LINT} is suitable for weakly coupled problems because it will transfer the full load in fewer stagger iterations. If you are using a single stagger iteration for each multi-field time step, you must use a relaxation value of 1.0 for all quantities.

\subsection*{4.2.3.6. List or Clear Settings}

To list or clear the analysis settings, use the command shown in the following table.
4.2.4. Obtain the Solution

If you are working interactively, use the commands shown in the following table to write the necessary input file.

<table>
<thead>
<tr>
<th>Step</th>
<th>Command</th>
<th>GUI Path</th>
</tr>
</thead>
<tbody>
<tr>
<td>Write the MFX input file</td>
<td>MFWRITE</td>
<td>Main Menu&gt; Preprocessor&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; &gt; Write input</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Main Menu&gt; Solution&gt; Multi-field Set Up&gt; MFX-ANSYS/CFX&gt; &gt; Write input</td>
</tr>
</tbody>
</table>

You cannot initiate a solution interactively. You must issue MFWRITE to write out the input file containing all of the MFX data, and then submit that input file as a batch job, along with the necessary CFX input. When you write out the input file using MFWRITE or via the launcher, ANSYS will add /SOLU, SOLVE, and FINISH commands at the end of the input file.

4.2.5. Multi-field Commands

The following table shows which commands are valid for multi-field analyses.

<table>
<thead>
<tr>
<th>Command</th>
<th>Valid for ANSYS Multi-field solver (MFS)</th>
<th>Valid for MFX</th>
</tr>
</thead>
<tbody>
<tr>
<td>MFANALYSIS</td>
<td>yes</td>
<td>yes</td>
</tr>
<tr>
<td>MFBUCKET</td>
<td>yes</td>
<td>yes</td>
</tr>
<tr>
<td>MFCALC</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFCLEAR</td>
<td>yes</td>
<td>yes</td>
</tr>
<tr>
<td>MFCMMAND</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFCONV</td>
<td>yes</td>
<td>yes</td>
</tr>
<tr>
<td>MFDTIME</td>
<td>yes</td>
<td>yes</td>
</tr>
<tr>
<td>MFELEM</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFEM</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFEXTER</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFNAME</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFIMPORT</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFINTER</td>
<td>yes</td>
<td></td>
</tr>
<tr>
<td>MFITER</td>
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<tr>
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</tr>
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</tr>
</tbody>
</table>
Valid for MFX
Valid for ANSYS Multi-field solver (MFS)

<table>
<thead>
<tr>
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<th>Valid for MFX</th>
</tr>
</thead>
<tbody>
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</tr>
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<td>MFVOLUME</td>
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<td></td>
</tr>
<tr>
<td>MFWRITE</td>
<td></td>
<td>yes</td>
</tr>
</tbody>
</table>

* Valid only for the ANSYS field in MFX.

4.2.6. Postprocess the Results

For information on postprocessing, refer to An Overview of Postprocessing in the ANSYS Basic Analysis Guide. To postprocess the fluid results, use CFX-Post.

4.3. Starting and Stopping an MFX Analysis

You can start an MFX analysis via the launcher or via the command line. Both methods are explained here.

4.3.1. Starting an MFX Analysis via the Launcher

When you start an MFX analysis via the launcher, the ANSYS launcher will start up both ANSYS and CFX. You must set up your analysis separately, following the instructions explained in MFX Solution Procedure. The procedure explained in this section opens the software with the proper licenses and settings, and runs the specified input files.

When using the launcher, you will be able to open and run CFX on the local machine only. If you will be running CFX on a different machine, you must use the command method described in Section 4.3.2: Starting an MFX Analysis via the Command Line.

You must be running on one of the following platforms: HP, SGI, Linux 32-bit, or Windows 32-bit.

Use the following procedure to start an MFX analysis via the launcher.

1. Open the ANSYS launcher:
   
   Windows:
   
   Start >Programs >ANSYS 10.0 >ANSYS Product Launcher
   
   UNIX:
   
   launcher100
   
2. Select the MFX - ANSYS/CFX simulation environment.
   
   The MFX - ANSYS/CFX Setup is displayed.
   
3. Select an applicable license. You must use an ANSYS Multiphysics (except Multiphysics 1, 2, or 3, or Batch Child) or Mechanical license. Only applicable licenses will appear.
   
4. On the MFX - ANSYS/CFX Setup tab, specify the ANSYS Run information:
   
   • Working directory (must be an absolute path on Windows)
   • Job name
   • Input file
5. Specify the CFX Run information:

- Working directory
- Definition file - the name of the slave input file
- Initial values file - valid only if a definition file is specified
- Additional command line options - cfx5solve command line options (use cfx5solve -help for more information on available command line options)
- CFX installation directory - You must enter the installation directory on UNIX platforms, even if you installed CFX in the default location. On Windows platforms, the default directory is provided, but you can change it. You may need to specify a non-default CFX installation directory if you have multiple versions of CFX installed on your machine, and the most recently installed version is NOT the version you want to use for this MFX operation. Additionally, on Windows systems only, you can restore the default setting.
- Number of partitions for local parallel runs. Distributed parallel runs are not supported from the launcher. However, if you are using CFX’s parallel processing capabilities (via the command line), you can still submit the ANSYS run from the launcher.

Note — When running MFX from the launcher, you must use ANSYS and CFX (uppercase) as the field solver names (MFPSIMUL) in your input file.

6. Click Run.

The launcher offers you additional tools to aid with your MFX analysis.

If you do not want to launch CFX from this launcher, you can unselect the Automatically start CFX run after starting ANSYS run option. If you choose not to start CFX automatically, you will need to manually start CFX before the MFX analysis will complete.

In the product settings area of the launcher, you have the choice to automatically launch the ANSYS Results Tracker, the CFX-Solver Manager, and the Interface Results Tracker. These tools allow you to monitor the progress of the MFX analysis as it proceeds. To use the ANSYS Results Tracker or the Interface Results Tracker, you must include the /GST,ON,ON command in your input listing. For more information on the ANSYS Results Tracker and the Interface Results Tracker, see the NLHIST command. For more information on the CFX-Solver Manager, see the CFX documentation (Help> Master Contents> Solver Manager).

You can also cancel the MFX run by clicking the Cancel Run button. This feature is useful if, while monitoring the progress, you find your analysis is not converging or encounters other problems. You can stop the run, make corrections to your inputs, and rerun the job. When you select Cancel Run, the MFX run will finish the current multi-field time step and stop the run cleanly.

4.3.1.1. Other Settings

You can further control launcher settings by using the ANS_LAUNCH_MFX_PORT_RANGE environment variable to control which port(s) to try to determine a listening port. Valid range is between 1024 and 65535. If you want to specify a range of ports to try, separate the range with a hyphen. For example, if you want the ports 50000
through 50050 to be tried, then set the environment variable to 50000-50050. The default port range is 49800 through 49899.

This feature is useful if you are running through a firewall that has only certain ports open. The `ANS_LAUNCH_MFX_PORT_RANGE` environment variable is valid only when using the ANSYS launcher to start an MFX analysis.

### 4.3.2. Starting an MFX Analysis via the Command Line

You can also start an MFX analysis via the command line using the following procedure.

**ANSYS Master** To launch the master ANSYS process, issue the following command:

```bash
ansys100 -p productname -mfm fieldname -ser port# -i inputname -o outputname
```

Where:

- `productname` is the ansys product variable. You must use a Multiphysics (except Multiphysics 1, 2, or 3, or Batch Child) or Mechanical license. See the Product Variable Table in the *ANSYS, Inc. Licensing Guide* for the product variables for these products.
- `fieldname` is the master field solver name as specified with the `MFLCOMM` and `MFPSIMUL` commands.
- `port#` is the listening port number. ANSYS recommends using a port number between 49512 and 65535. ANSYS will create a `jobname.port` file that contains the port number if you do not include the `-ser port#` option on the command line. You can then use this port number for the CFX run. You must start ANSYS first to generate the `jobname.port` file.
- `inputname` and `outputname` are the input and output filenames.

**CFX Slave** To launch the slave CFX process, issue the following command:

```bash
cfx5solve -def inputfile -cplg-slave fieldname -cplg-host port#@ansys_hostname
```

Where:

- `inputname` is the CFX input (definition) file
- `fieldname` is the slave field solver name as specified with the `MFLCOMM` and `MFPSIMUL` commands.
- `port#@ansys_hostname` is the listening port number initialized by the ANSYS master and the host name of the master machine.

### 4.3.3. Stopping an MFX Run Manually

You can stop an MFX run by using the **Cancel Run** button on the launcher. To stop an MFX run manually, create a text file named `Jobname_mfx.ABT`, with MFX in the first line. This file must reside in the master’s working directory. Once this file is in place, MFX will stop cleanly after finishing the current multi-field time step.

To monitor the progress and field convergence in an MFX analysis, you can use the tracking tools available on the launcher, or you can manually launch the convergence tracker in ANSYS by issuing `NLHIST100`. In order to monitor the analysis, you must include `/GST,ON,ON` in your input file. This command will create the `Jobname.NLH` file for interface convergence and the `ANSYS.GST` file for the ANSYS field convergence. You must use the CFX Solver Manager to monitor CFX convergence.
4.4. Example Simulation of a Piezoelectric Actuated Micro-Pump

4.4.1. Problem Description

The working principle of micro-pumps is the actuation of a flexible membrane to obtain the driving pressure for the fluid flow. Electro-thermal, electrostatic, or piezoelectric actuators are most commonly used for this purpose.

The benchmark problem is taken from A. Klein and demonstrated in Figure 4.5: “Piezoelectric Micropump Description”. This device consists of a fluid chamber with a deformable membrane at the top. The membrane is actuated by a piezoelectric layer during pump operation. To estimate the fluid damping and inertial forces on the membrane, a simplified process of the membrane actuation is considered here. With the diaphragm in the neutral position and the chamber filled with the working fluid, the PZT layer is actuated at t = 0 with an electric field, which is maintained at a constant level subsequently.

Figure 4.5 Piezoelectric Micropump Description

ANSYS coupled field element SOLID98 with displacement and voltage DOFs is used for the piezoelectric material and SOLID95 is used for the silicon membrane. Air at 25 degrees Celsius is used as the working fluid for the CFX solver.

The following material properties were used for the silicon:

- Young’s Modulus: 1.689e11 Pa
- Poisson’s ratio: 0.3
- Density: 2329 kg/m³

The following material properties were used for the piezoelectric material:

- Density: 7500 kg/m³
- X and Z Permittivity: 804.6 F/m (Polar axis along Y axis)
- Y Permittivity: 659.7 F/m

The elasticity matrix is shown here:

$$
[C] = 10^{10} \begin{bmatrix}
13.2 & 7.3 & 7.1 & 0 & 0 & 0 \\
7.3 & 11.5 & 7.3 & 0 & 0 & 0 \\
7.1 & 7.3 & 13.2 & 0 & 0 & 0 \\
0 & 0 & 0 & 2.6 & 0 & 0 \\
0 & 0 & 0 & 0 & 2.6 & 0 \\
0 & 0 & 0 & 0 & 0 & 3 \\
\end{bmatrix}
$$

The piezoelectric strain matrix is shown here:
\[
[P] = \begin{bmatrix}
0 & -4.1 & 0 \\
0 & 14.1 & 0 \\
0 & -4.1 & 0 \\
10.5 & 0 & 0 \\
0 & 0 & 10.5 \\
0 & 0 & 0 \\
\end{bmatrix}
\]

Figure 4.6 Model Dimensions

This model has a 0.1 mm thickness in the z direction, and both side surfaces have a \( U_z = 0 \) boundary condition for the structural part, and a symmetry condition for the fluid part.

Figure 4.7 Model Boundary Conditions

4.4.2. Set Up the Piezoelectric and Fluid Inputs

The first step in this example is to create two ANSYS .cdb files, one to set up the piezoelectric analysis and one to set up the fluid analysis. These files will be imported into the MFX solver. You will create these files with two batch ANSYS runs using the input files piezo.inp and CFXfluid.inp, respectively. This example provides the models (under /ansys_inc/v100/ansys/data/models); you must be familiar with setting up a piezoelectric analysis and familiar with creating a CFX fluid mesh.
You will then set up the CFX model in CFX-Pre and create the CFX definition file following the steps provided in Section 4.4.3: Set up the CFX Model and Create the CFX Definition File. Finally, step by step instructions are provided in Section 4.4.4: Set Up the MFX Controls for interactively setting the MFX input and creating the MFX input file. This will then be executed through the MFX launcher.

It is important that you enter all names exactly as shown in this example, including spaces and underscores. ANSYS and CFX use these names in their communication during the solution.

To create the two ANSYS .cdb files, follow the steps below:

1. Open the ANSYS Launcher.
   - Windows: Choose menu path Start> Programs> ANSYS 10.0> ANSYS Product Launcher.
   - UNIX: Type launcher100.
2. Select the Simulation Environment ANSYS Batch.
3. Select a multiphysics license.
4. The File Management tab is activated by default. In the File Management tab:
   - Enter the working directory where the piezo.inp and CFXfluid.inp files are located. You can type this directory in or select it via browsing.
   - Enter a unique jobname.
   - Enter piezo.inp for the input file.
   - Enter piezo.out for the output file.
5. Click Run. This input file will create the pfsi-solid.cdb file to be used later.

Repeat this process for the CFXfluid.inp file, using CFXfluid.inp as the input file name, and CFXfluid.out as the output file name. This input file will create the fluid.cdb file that will be used later.

4.4.3. Set up the CFX Model and Create the CFX Definition File

Set up the example in the CFX preprocessor

1. Start CFXpre from the CFX launcher.
2. Create a new simulation and name it cfx_mfxexample.
3. Load the mesh from the ANSYS file named fluid.cdb. The mesh format is ANSYS. Accept the default unit of meters for the model.
4. Define the simulation type:
   1. Set Option to Transient.
   2. Set Time duration - Total time to 5E-4 s. Note: this value will be overridden by ANSYS.
   3. Set Time steps - Timesteps to 5E-6 s. Note: this value must be equal to the time step set in ANSYS.
   4. Set Initial time - Option to Value, and accept the default of 0 s.
5. Create the fluid domain and accept the default domain name. Use Assembly as the location.
6. Edit the fluid domain using the Edit domain - Domain1 panel.
1. Set **Fluids list** to Air at 25 C.

2. Set **Mesh deformation - Option** to Regions of motion specified. Accept the default value of mesh stiffness.

3. In the **Fluid models** tab, set **Turbulence model - Option** to None (laminar).

4. Accept the remainder of the defaults.

5. Initialize the model in the **Initialisation** tab. Click **Domain Initialisation**, and then click **Initial Conditions**. Select Automatic with value and set velocities and static pressure to zero.

7. Create the interface boundary condition. This is not a domain interface. Set **Name** to Interface1.
   
   1. In the **Basic settings** tab: Set **Boundary type** to Wall. Set **Location** to FSI.
   
   2. In the **Mesh motion** tab: Set **Mesh motion - Option** to ANSYS Multifield.
   
   3. Accept the defaults for boundary details.

8. Create the opening boundary condition. Set **Name** to Opening.
   
   1. In the **Basic settings** tab: Set **Boundary type** to Opening. Set **Location** to Opening.
   
   2. In the **Boundary details** tab: Set **Mass and momentum - Option** to Static pres. (Entrain). Set **Relative pressure** to 0 Pa.
   
   3. In the **Mesh motion** tab: Accept the **Mesh motion - Option** default of Stationary.

9. Create the wall boundary condition. Set **Name** to Bottom. Edit the wall boundary condition using **Edit boundary: Bottom in Domain: Domain1** panel.
   
   1. In the **Basic settings** tab: Set **Boundary type** to Wall. Set **Location** to Bottom.
   
   2. In the **Boundary Details** tab: Set **Wall influence on flow - Option** to No slip.
   
   3. In the **Mesh motion** tab: Set **Mesh motion** to Stationary.

10. Create another wall boundary condition. Set **Name** to Top. Edit the wall boundary condition using **Edit boundary: Top in Domain: Domain1** panel.

   1. In the **Basic settings** tab: Set **Boundary type** to Wall. Set **Location** to Top.
   
   2. In the **Boundary Details** tab: Set **Wall influence on flow - Option** to No slip.

   3. In the **Mesh motion** tab: Set **Mesh motion** to Stationary.

11. Create the end symmetry boundary condition. Set **Name** to Sym.

   1. In the **Basic settings** tab: Set **Boundary Type** to Symmetry. Set **Location** to Pipe.

   2. In the **Mesh motion** tab: Set **Mesh motion** to Unspecified.

12. Create the side symmetry boundary condition. Set **Name** to Symmetry. Edit the symmetry boundary condition using **Edit boundary: Side1 in Domain: Domain1** panel.

   1. In the **Basic settings** tab: Set **Boundary type** to Symmetry. Set **Location** to Side1 and Side2. Use the **Ctrl** key to select multiple locations.

   2. In the **Mesh motion** tab: Set **Mesh motion** to Unspecified.
13. Accept the defaults for Solver Control.
14. Generate transient results to enable post processing through the simulation period.
   1. Click Output Control.
   2. Go to Trn Results tab.
   3. Create New. Accept Transient Results as the default name.
   4. Choose Time Interval and set to 5E-5.
   5. Accept the remaining defaults.
15. Create the CFX definition file.
   1. Choose menu path File> Write Solver File. Name the file cfx_mfxexample.def.
   3. Click Quit CFX Pre.
   4. Click OK.

4.4.4. Set Up the MFX Controls

Follow the steps below to set up the MFX controls in ANSYS. The first step reads in the pfsi-solid.cdb input file, which includes the preliminary model and preprocessing information.

Specify MFX

1. Open the ANSYS Launcher.
   Windows: Choose menu path: Start> Programs> ANSYS 10.0> ANSYS Product Launcher
   UNIX: Type launcher100.
2. Select an ANSYS Multiphysics license.
3. Set your working directory or any other settings as necessary. See Section 3.2: The ANSYS Launcher in the ANSYS Operations Guide for details on using the ANSYS launcher.
4. Click Run.
5. When ANSYS has opened, choose menu path Utility Menu> File> Read Input From and navigate to the file pfsi-solid.cdb. Click OK.
6. Choose menu path Main Menu> Solution> Multi-field Set Up> Select Method.
7. For the MFS/MFX Activation Key, click ON.
8. Click OK.
9. Click MFX-ANSYS/CFX and click OK.

Set Up the MFX Groups

1. Choose menu path Main Menu> Multi-field Set Up> MFX-ANSYS/CFX> Solution Ctrl.
2. Select Sequential. Enter .5 for the relaxation value and click OK.
3. On the next dialog box, for Select Order, choose Solve ANSYS First and click OK.
Set Up the MFX Time Controls and Load Transfer

1. Choose menu path **Main Menu> Multi-field Set Up> MFX-ANSYS/CFX> Load Transfer**.
2. Enter Interface1 for the **CFX Region Name**.
3. For **Load Type**, accept the default of Mechanical.
4. Click **OK**.
5. Choose menu path **Main Menu> Multi-field Set Up> MFX-ANSYS/CFX> Time Ctrl**.
6. Set **MFX End Time** to 5e-4.
7. Set **Initial Time Step** to 5e-6.
8. Set **Minimum Time Step** to 5e-6.
9. Set **Maximum Time Step** to 5e-6.
10. Accept the remaining defaults and click **OK**.

Set Up MFX Advanced Options

1. Choose menu path **Main Menu> Multi-field Set Up> MFX-ANSYS/CFX> Advanced Set Up> Iterations**.
2. Note the defaults and click **OK**.
3. Choose menu path **Main Menu> Multi-field Set Up> MFX-ANSYS/CFX> Advanced Set Up> Convergence**.
4. Select **All** and click **OK**.
5. On the next dialog box, accept the default of 1.0e-3 for **Convergence for All Items** and click **OK**.
6. In the **Command Input** window, type **MFOU ,1** to write the output for every time step.
7. In the Command Input window, type **KBC ,1** to specify stepped loading.
8. Choose menu path **Main Menu> Multi-field Set Up> MFX-ANSYS/CFX> Write input**. Name the file **mfxexample.dat**.
9. Exit ANSYS.

4.4.5. Run the Example from the ANSYS Launcher

1. Open the ANSYS Launcher.
2. Select **MFX - ANSYS/CFX** as the simulation environment.
3. In the **MFX - ANSYS/CFX Setup** tab:
   - Enter the ANSYS working directory you have been using. You can type this directory in or select it via browsing.
   - Enter **ansys_mfxexample** for the ANSYS jobname.
   - Enter **mfxexample.dat** for the ANSYS input file.
   - Enter **mfxexample.out** for the ANSYS output file.

Specify the following CFX settings:
   - CFX Working Directory
Enter `cfx_mfxexample.def` for the CFX definition file. You can leave the remaining CFX settings blank.

4. Click Run.

**View the Results**

You can view results from both the ANSYS and the CFX portions of the run. The following figure shows the response of the vertical displacement of the silicon membrane’s center point (ANSYS).

**Figure 4.8 Vertical Displacement of the Silicon Membrane's Center Point**

The following figure shows the von Mises stress distribution for piezoelectric and silicon layer at $t = 500 \mu s$ (ANSYS).
Figure 4.9 von Mises Stress Distribution

The following figure shows air streamline velocity from CFX at $t = 500 \mu s$ (CFX).
Figure 4.10  Air Streamline Velocity
Chapter 5: Unidirectional ANSYS to CFX Load Transfer

Sometimes you can couple a fluid-solid interaction analysis by unidirectional load transfer. This method requires that you know that the fluid analysis results do not affect the ANSYS loads significantly. Loads from an ANSYS Multiphysics analysis can then be unidirectionally transferred to a CFX fluid analysis. The load transfer occurs external to the analyses.

The unidirectional ANSYS to CFX load transfer method is available in the ANSYS Multiphysics product. It supports all ANSYS 3-D structural (solid and shell), thermal, electromagnetic, and coupled-field elements. The coordinate system must be global Cartesian. Valid load types are: displacement, temperature, and heat flux for 2-D surface loads, and displacement, force density and heat generation for 3-D loads.

The following unidirectional load transfer topics are available:

5.1. The Unidirectional Load Transfer Method
5.2. Sample Unidirectional Load Transfer Analysis

5.1. The Unidirectional Load Transfer Method

ANSYS performs a solid analysis and writes out a load profile file. ANSYS also generates and writes out solid and fluid meshes. The CFX Pre-Processor reads the ANSYS load profile and mesh files and starts a fluid analysis.

The ANSYS Multiphysics procedure for creating a load profile file is as follows.

1. Flag field surface and volume interfaces for load transfer. Flagged surfaces sharing a common surface interface number will exchange surface load data; flagged volumes sharing a common volume interface number will exchange volume load data.

For surface load transfer across fields, use the following SF family of commands and the FSIN surface load label. Use \texttt{VALUE2/VAL2/VALJ} to specify the surface interface number.

\begin{align*}
\texttt{SF, Nlist, Lab, VALUE, VALUE2} \\
\texttt{SFA, AREA, LKEY, Lab, VALUE, VALUE2} \\
\texttt{SFE, ELEM, LKEY, Lab, KVAL, VAL1, VAL2, VAL3, VAL4} \\
\texttt{SFL, LINE, Lab, VALI, VALJ, VAL2I, VAL2J}
\end{align*}

For volumetric load transfer, use the \texttt{BFE} command and the FVIN volume load label. Use \texttt{VAL2} to specify the volume interface number.

\begin{align*}
\texttt{BFE, ELEM, FVIN, STLOC, VAL1, VAL2, VAL3, VAL4}
\end{align*}

For additional information on the FSIN and FVIN labels, see the SF family of commands and the \texttt{BFE} command in the \textit{ANSYS Commands Reference}.

2. Specify the units of the transferred loads by issuing the following command:

\begin{align*}
\texttt{EXUNIT, Ldtype, Load, Untype, Name}
\end{align*}

Valid surface loads (Ldtype = SURF) are: \texttt{DISP} (displacement), \texttt{TEMP} (temperature), and \texttt{HFLU} (heat flux). Valid volumetric loads (Ldtype = VOLU) are: \texttt{DISP} (displacement), \texttt{FORC} (force), and \texttt{HGEN} (heat generation). \texttt{FORC} and \texttt{HGEN} are per unit volume. You can specify a predefined unit system (Untype = COMM) or your own unit system that must be recognizable by CFX (Untype = USER).
The predefined unit names are:

- Surface Load Metric: SI
- Volume Load Metric: SI
- Surface Load English: FT
- Volume Load English: FT

**EXUNIT** must be issued before the **EXPROFILE** command.

3. Write the profile file for CFX by issuing the following command in POST1.

```
EXPROFILE, Ldtype, LOAD, VALUE, Pname, Fname, Fext, Fdir
```

You need to specify a surface or volume interface number (*VALUE*) for the load, field and file names for the profile file (*Pname* and *Fname*), and a profile file extension and directory (*Fext* and *Fdir*). If you want to export multiple loads, you need to specify a unique file name for each load.

### 5.2. Sample Unidirectional Load Transfer Analysis

In this example, a wire in air is heated by a current passing through it. The amount of energy produced by Joule heating is determined by ANSYS and transferred to CFX. The wire has temperature independent material properties, and therefore the amount of Joule heating is not affected by the cooling of the wire. CFX performs a conjugate heat transfer analysis of a solid (the wire) with natural convection cooling and a volumetric heat source.

Henceforth, the ANSYS thermal-electric part of the analysis that determines the Joule heating load for transfer to CFX is referred to as the “solid analysis.”

ANSYS performs the following tasks:

1. Solves a solid transient analysis and writes out a profile file of heat generation rates.
2. Generates and writes out the mesh for the fluid region.
3. Generates and writes out the mesh for the solid region.

### 5.2.1. ANSYS Command Listings

You can perform the ANSYS tasks using the commands shown below. Text prefaced by an exclamation point (!) is a comment.

#### 5.2.1.1. Solve Solid Analysis and Write Profile File

```
/prep7
/triad,off
/et,1,226,110
/et,2,200,6
!*****************************************
! MKS units
!*****************************************
!
! Thermal conductivity of copper, Watts/m*Deg-C
mp,kxx,1,370.0
!
! resistivity of copper, Ohm*m
mp,rsvx,1,3.00e-8
!
! density of copper (kg/m3)
mp,dens,1,8933.
!
! specific heat
mp,c,1,385.
```
! Geometry
wd = .0005
wl = .0005
esizew = wd/5
esizea = wd/2
CTRL,0,0,wd
wpro,,,90
asbw,all
adelete,3,,,1
! Area 2 is an end of the wire
lcomb,1,4
! Wire
voff,2,wl
! Set meshing element
alls
type,2
esize,esizew
amesh,2
! - volumetric mesh
nlenw=4
rlen=1
lesize,4,,,nlenw,rlen
! Mesh the wire
type,1 ! set element type
mat,1
vsweep,1
! Boundary and initial conditions
nsel,r,loc,z,0
cp,1,volt,all
f,1,amps,20
nsel,s,loc,z,wl
d,all,volt,0,1 ! back end, set voltage to zero
! Assigning export ID
alls
aclear,all
etdele,2
bfe,all,fwin,,0,1
! fini
/solu
!
tunif,303
ic,all,temp,303
antype,trans
deltim,.2,.2,.2
oures,all,5
kbc,1
eqslv,sparse
time,2.0
solve
save
fini
/post1
exun,volu,disp,comm,si
exun,volu,hgen,comm,si
expr,volu,hgen,1,'wire heat',wireprof,csv

5.2.1.2. Generate and Write Fluid Region Mesh

/prep7
/triad,off
et,1,142
et,2,200,6
!**************************************************************
! MKS units
!**************************************************************
! Geometry
wd = .0005
wl = .0005
esizew = wd/5
esizea = wd/2
CYL4,0,0,wd, ,3*wd
CYL4,0,0,3*wd, ,8*wd
RECTNG,0,15*wd,-20*wd,20*wd
wpro,,,90
asbw,all
asel,s,,,5,7,2
adelete,all,;,1
nummrg,kp
! Area 5 is an end of the wire
alls
isel,s,,,9,12,3
asbl,3,all
adelele,1,,,1
! Areas 2,4,6 are the ends of the air
alls
lcomb,12,9
lcomb,4,1
lcomb,5,8
! Some lesizes for fluid mesh
nradi=15
rri = 5
nrado=12
rro = 2
naz=30
lesize,21,,,nradi,1/rri
lesize,22,,,nradi,1/rri
lesize,23,,,nrado,1/rro
lesize,24,,,nrado,1/rro
isel,s,,,1,9,4
lesize,all,,,naz
alls
! - Fluid
voff,4,wl
voff,6,wl
voff,2,wl
nummrg,kp
! Set meshing element
alls
type,2
amesh,4
amesh,6
esize,esizea
alls
amesh,2
! - Volumetric mesh stuff
nlen=10
rlen=-2
! Lines in the horizontal direction for fluid
isel,a,,,10,13
isel,a,,,25,26
isel,a,,,35,38
lesize,all,,,nlen,rlen
alls
! Mesh the fluid
type,1
mat,1
lesize,8,,,nradi,rri
lesize,20,,,nrado,rro
vsweep,all
numcmp,node
numcmp,elem
! - Utilize existing mesh200 for boundary name
! - CFD boundary condition
esel,s,type,;2
cm,zeroend,elem
alls
! CFD boundary conditions
! Condition on interface
asel,s,,,7
amesh,7
5.2.1.3. Generate and Write Solid Region Mesh

/prep7
/triad,off
et,1,142
et,2,200,6
!******************************************************************************
! MKS units
!******************************************************************************
! Thermal conductivity of copper, Watts/m*Deg-C
mp,kxx,1,370.0
! resistivity of copper, Ohm*m
mp,rsvx,1,3.00e-8
! density of copper (kg/m3)
mp,dens,1,8933.
! specific heat
mp,c,1,385.
!
!
! Geometry
wd = .0005
wl = .0020
esizew = wd/5
esizea = wd/2
CYL4,0,0,wd
wpv,,90
asbw,all
adelete,3,,,1
! Area 2 is an end of the wire
lcomb,1,4
! - Wire
voff,2,w1
! Set meshing element
alls
type,2
esize,esizew
amesh,2
5.2.2. CFX Procedure

You can then perform the following CFX procedure. For detailed instructions on how to perform the steps below, refer to the CFX Pre documentation.

1. Select File -> Import Mesh to import both the fluid and solid domain meshes by selecting the mesh format of ANSYS and entering the two cdb file names.
2. Select Create -> Flow Object -> Simulation Type to set the steady state option.
3. Select Create -> Flow Object -> Domain to create domain model, fluid/solid model and domain initialization for both the fluid and solid domains.
4. Select Create -> Flow Object -> Boundary Conditions to set the inlet, outlet and symmetry boundaries in the fluid domain and wall boundary in the solid domain.
5. Select Create -> Flow Object -> Domain Interface to set the "Fluid Solid" conjugate heat transfer interface.
6. Select Create -> Flow Object -> Solver Control to set the solver control options.
7. Select Tools -> Initialize Profile Data, and enter the profile name that was just generated by ANSYS.
8. Select Create -> Flow Object -> Subdomain, and select the assembly that is the same as the solid domain. Set the energy source using the imported profile data by selecting energy in Equation Sources and Source in the energy Option and enter "wire heat enysou(x,y,z)" in the Source. For more information, refer to Use Profile Data in the CFX Pre documentation.
9. Select File -> Write Solver File to start the solver manager.
Chapter 6: Reduced Order Modeling

This chapter describes a solution method for efficiently solving coupled-field problems involving flexible structures. This reduced order modeling (ROM) method is based on a modal representation of the structural response. The deformed structural domain is described by a factored sum of the mode shapes (eigenvectors). The resulting ROM is essentially an analytical expression for the response of a system to any arbitrary excitation.

This methodology has been implemented for coupled electrostatic-structural analysis and is applicable to micro-electromechanical systems (MEMS).

The solver tool enables essential speed up for two reasons:

- A few eigenmodes accurately represents the dynamic behavior of most structures. This is particularly true for micro-electromechanical systems (MEMS).
- Modal representations of electrostatic-structural domains are very efficient because just one equation per mode and one equation per conductor are necessary to describe the coupled domain system entirely.

This modal method can be applied to nonlinear systems. Geometrical nonlinearities, such as stress stiffening, can be taken into account if the modal stiffness is computed from the second derivatives of the strain energy with respect to modal coordinates. Capacitance stroke functions provide nonlinear coupling between eigenmodes and the electrical quantities if stroke is understood to be modal amplitude.

For more information on this method, see Reduced Order Modeling of Coupled Domains in the ANSYS, Inc. Theory Reference.

The process involves the following distinct steps.

**Figure 6.1 ROM Flowchart**

The model preparation step creates the necessary finite element model for the generation pass. The generation pass executes a modal analysis of the structure. It also executes an optional static analysis to determine the deformation state of the structure under operating conditions. Using this information, the generation pass then selects the modes and performs computations to create a reduced order model. The use pass uses the reduced
order model in an analysis. The reduced order model is stored in a ROM database and a polynomial coefficients file, and utilized by a ROM element (ROM144). The expansion pass extracts the full DOF set solution and computes stresses on the original structure created in the model preparation phase. A VHDL-AMS mathematical model of the ROM structure may be exported for use in electrical design automation (EDA) system simulators.

The ROM method is applicable to 2-D and 3-D models. The generation pass requires multiple finite element solutions of the structural and electrostatic domains, where the structure is displaced over its operating range. To support both morphing and remesh operations for the multiple finite element solutions, PLANE121, SOLID122, or SOLID123 elements must model the electrostatic domain. INFIN110 or INFIN111 elements can model the open boundary of electrostatic fields if required. 2-D or 3-D structural or shell elements can model the structural domain. Care must be exercised when preparing the model of the electrostatic domain to ensure that morphing or remeshing will succeed over the deflection range of the structure. For more information on mesh morphing, see Section 2.4.1: Mesh Updating.

The ROM characterization requires that the device operate primarily in one dominant direction (X, Y, or Z in the global Cartesian system). This includes not only the transversal shift of most rigid bodies (inertial sensors), but also cantilever and plate bending (RF filters, pressure gauges, ultrasonic transducers) and swivel motions (micromirrors). Material properties must be elastic and temperature independent. Stress stiffening and prestress effects are available.

The following ROM topics are available:

6.1. Model Preparation
6.2. Generation Pass
6.3. Use Pass
6.4. Expansion Pass
6.5. Sample Miniature Clamped-Clamped Beam Analysis (Batch or Command Method)
6.6. Sample Micro Mirror Analysis (Batch or Command Method)

6.1. Model Preparation

Model preparation includes all steps that are necessary to create a finite element model database and physics files for the generation pass. The following flowchart illustrates the process involved.

Figure 6.2 Model Preparation Flowchart

Diagram of the model preparation process with steps including:
- Build the Solid Model
- Mesh the Model
- Create Structural Physics File STRU
- Create Electrostatic Physics File ELEC
- Save Model Database (SAVE,MODEL, DB)

Produced files:
- MODEL.ph1
- MODEL.ph2
- MODEL.db

Each step is explained in detail below:
6.1.1. Build the Solid Model
6.1.2. Mesh the Model
6.1.3. Create Structural Physics File
6.1.4. Create Electrostatic Physics File
6.1.5. Save Model Database

6.1.1. Build the Solid Model

As a first step, you must build a solid model of the structure, and the electrostatic field surrounding the structure. To build the model, you must specify a jobname (for example, MODEL) using either of the following:

- **Command(s):** /FILNAME
- **GUI:** Utility Menu> File> Change Jobname

You use the PREP7 preprocessor to define the element types, element real constants, material properties, and the model geometry. For information on how to build a solid model, see Section 1.1: Building the Model in the ANSYS Basic Analysis Guide and Chapter 5, “Solid Modeling” in the ANSYS Modeling and Meshing Guide.

6.1.2. Mesh the Model

Once you have built your solid model, you are ready to generate the finite element mesh. For information on meshing techniques, see Chapter 7, “Generating the Mesh” in the ANSYS Modeling and Meshing Guide.

6.1.3. Create Structural Physics File

Next, you must create a structural physics file entitled “STRU” in accordance with the physics environment approach described in Chapter 2, “Sequentially Coupled Physics Analysis”. It must include material properties, real constants, fixed zero boundary conditions, and initial prestress conditions. Some important points to remember are:

- Apply all zero-value displacement constraints to solid model entities.
- Do not apply any nonzero displacement or nodal forces in the model database. These can be applied later during the use pass at specific master nodes.
- Apply prestress conditions in the model database by means of thermal stress. Specify appropriate element temperatures and thermal expansion coefficients.
- Do not apply element loads (pressure, or gravity loading) in the model database. These types of loads may be specified later in the Generation Pass.
- Group nodes on which eigenmodes will be imposed during the generation pass into a node component called “NEUN.” Limit the number of nodes to 5000 minus the number of defined scalar parameters in the model. Select a distributed subset of the nodes on the neutral plane if this limit is exceeded.
- In order to obtain a proper set of strain energy and capacitance information in the design space, the movable structure must be displaced to various linear combinations of their eigenmodes. Those deformation states are internally imposed by appropriate displacement constraints in the operating direction. In practice, it is unnecessary to impose displacement constraints on all structural nodes. It is sufficient to just choose nodes on a neutral plane of the structure, which is perpendicular to the operating direction. This allows the structure to relax properly and it is especially necessary for stress stiffened structures. If the device does not undergo stress stiffening, then any plane of nodes perpendicular to the operating direction may be selected.

You use either of the following to create the structural physics file (MODEL.ph1).

- **Command(s):** PHYSICS,WRITE,STRU
- **GUI:** Main Menu> Preprocessor> Physics> Environment
6.1.4. Create Electrostatic Physics File

Next, you must create an electrostatic physics file entitled “ELEC” in accordance with the physics environment approach described in Chapter 2, “Sequentially Coupled Physics Analysis”. It must include material properties and conductor specifications. Some important points to remember are:

- Group nodes of each conductor into components "CONDi," where i is a successive number assigned to each conductor.
- Group all volumes (3-D analysis) or all areas (2-D analysis) to be morphed or remeshed into a component called “AIR.”
- Do not apply zero and nonzero voltage loads and imposed current to the model database. These excitations and boundary conditions can only be applied during the use pass.

You use either of the following to create the electrostatic physics file (MODEL.ph2).

- **Command(s):** PHYSICS,WRITE,ELEC
- **GUI:** Main Menu> Preprocessor> Physics> Environment

6.1.5. Save Model Database

At this point, you need to save your database for use in the rest of the ROM procedure. The file name defaults to the Jobname (MODEL).

- **Command(s):** SAVE
- **GUI:** Utility Menu> File> Save as Jobname.db

6.2. Generation Pass

The generation pass includes all steps that are necessary to execute modal and static analyses, extract displacement and eigenvector information, and create a reduced order model of the structure. The reduced order model generation procedure is time consuming but it only has to be done once. After a reduced order model is established, you can perform any type of analysis with speed typical of system or circuit simulators and accuracy typical of finite element models. The generation pass consists of the following steps.
The following sections describe each step.

6.2.1. Specify Generation Pass Jobname
6.2.2. Assign ROM Features
6.2.3. Assign Names for Conductor Pairs
6.2.4. Specify ROM Master Nodes
6.2.5. Run Static Analysis for Test Load and Extract Neutral Plane Displacements
6.2.6. Run Static Analysis for Element Loads and Extract Neutral Plane Displacements
6.2.7. Perform Modal Analysis and Extract Neutral Plane Eigenvectors
6.2.8. Select Modes for ROM
6.2.9. Modify Modes for ROM
6.2.10. List Mode Specifications
6.2.11. Save ROM Database
6.2.12. Run Sample Point Generation
6.2.13. Specify Polynomial Order
6.2.14. Define ROM Response Surface
6.2.15. Perform Fitting Procedure
6.2.16. Plot Response Surface
6.2.17. List Status of Response Surface
6.2.18. Export ROM Model to External System Simulator

6.2.1. Specify Generation Pass Jobname

The jobname takes on special significance in reduced order model generation. By using jobnames effectively, you can eliminate much of the file handling inherent in a three-pass analysis. You should specify different jobnames for the generation pass and the use pass (for example, GEN and USE). /FILNAME,GEN will give the jobname GEN to all the files produced by the generation pass.

Command(s): /FILNAME
GUI: Utility Menu> File> Change Jobname

6.2.2. Assign ROM Features

In this step, you assign the model database (prepared in the model preparation phase), the dimensionality of the model, and the primary operating direction of the device.

Command(s): RMANL, /RESU
GUI: Main Menu> ROM Tool> Setup> Model Features
Utility Menu> File> Resume from

6.2.3. Assign Names for Conductor Pairs

You assign names to pairs of conductors to represent lumped capacitances. Conductors that interact in the operation of the device should be assigned as conductor pairs.

Command(s): RMCAP, RMCLIST
GUI: Main Menu> ROM Tool> Setup> Capacitances> Define
Main Menu> ROM Tool> Setup> Capacitances> List

6.2.4. Specify ROM Master Nodes

If nonzero boundary constraints, temporary zero boundary constraints or structural nodal forces will be applied in the use pass, you must declare nodes used as ROM master nodes. Furthermore, ROM master nodes are necessary to attach other elements to the ROM model (for example, COMBIN40) or to simply monitor nodal displacements during the use pass. There can be up to ten ROM master nodes representing the displacement in the operating direction. Master node displacements in the operating direction will be stored as UX degrees of freedom.

Command(s): RMASTER, RMALIST
GUI: Main Menu> ROM Tool> Setup> Master Nodes> Define
Main Menu> ROM Tool> Setup> Master Nodes> List
6.2.5. Run Static Analysis for Test Load and Extract Neutral Plane Displacements

To assist the program in determining which eigenmodes of the device are important in characterizing the structural response of the system under operating conditions, you should run a static analysis with a "test" load which deforms the structure in the operating direction of choice. The loads should drive the structure to a typical deformation state, which is representative of most load situations seen in the use pass. The amount of applied loads, the resulting displacements and even the accuracy of the computed results are not important because only ratios between modal coordinates are evaluated. The simplest test load could be in the form of imposed displacements. Alternatively, if you cannot define a test load, the modes and their amplitude range will be determined with respect to the linear modal stiffness ratios in the operating direction (see RMMSELECT).

The difference between using or not using a test load can be illustrated by a model of a beam clamped at both ends and suspended above a ground plane. For example, a voltage test load applied on the movable structure excites only symmetric eigenmodes in the operating direction. The RMMSELECT macro would select the symmetric modes in the order that corresponds to their displacement amplitudes. On the other hand, if no test load is specified, the RMMSELECT macro would select the lowest symmetric and asymmetric modes in the operating direction.

After you run a static analysis for a test load, you need to extract the neutral plane displacements.

Command(s): RMNDISP
GUI: Main Menu> General Postproc> ROM Operations> Extract NP Disp.

Note — The neutral plane nodes were grouped into a node component named NEUN in the model preparation phase.

6.2.6. Run Static Analysis for Element Loads and Extract Neutral Plane Displacements

If the device is subjected to gravity loads, or pressure loading, you must run a static analysis for each individual element load prior to creating the reduced order model. The effects of the element loading are considered in the mode selection for the reduced order model. Additionally, the element loads may be applied in the use pass when their effects on the device response are required.

Each individual element load must be run as a separate load case in a multi load-step static analysis. Up to five element loads can be imposed in the generation pass. Later, in the use pass, the loads can be scaled and superimposed using RMLVSSCALE.

After you run the analysis, you need to extract the neutral plane displacements.

Command(s): RMNDISP
GUI: Main Menu> General Postproc> ROM Operations> Extract NP Disp.

Note — NLGEOM must be OFF for linear and stress-stiffened structural models unless prestress is relevant. Here, the element loads must be moderate so that no deflection dependent change of stiffness occurs. The rule of thumb is that the resulting displacements must be between 0.001 and 0.1 times the device thickness.

6.2.7. Perform Modal Analysis and Extract Neutral Plane Eigenvectors

Next, you perform a modal analysis (ANTYPE,MODAL) with modal expansion (MXPAND) for the desired range of modes to be considered. The modal analysis captures modes of the device that will characterize the structural response. The ROM method assumes that the lowest modes dominate the structural response. You may need
to constrain the device motion in order to ensure that the dominant modes are captured as the lowest modes in the modal analysis.

You then extract the eigenvectors of the neutral plane nodes (component NEUN).

Command(s): RMNEVEC
GUI: Main Menu> General Postproc> ROM Operations> Extract NP Eigv.

### 6.2.8. Select Modes for ROM

Selection of the pertinent modes and their operating range is an essential step in the efficient and accurate determination of the reduced order model. You can use the results of the modal analysis and the test load and element load static analyses to determine the most appropriate modes to characterize the structural response. To perform an automated mode selection that uses those results, issue RMMSELECT with Method = TMOD.

Command(s): RMMSELECT, Nmode, Method, Dmin, Dmax
GUI: Main Menu> ROM Tool> Mode Selection> Select

The following are important points to remember at this step:

- Modes considered for use in the ROM are classified as "DOMINANT" or "RELEVANT." Dominant modes are those with expected large displacement amplitudes. Their amplitudes interact with all system parameters derived from the strain energy and capacitance functions. Either one or two dominant modes are allowed. Relevant modes are those with expected small displacement amplitudes. Their behavior is strongly influenced by the amplitude of dominant modes but the interaction between the relevant modes can be neglected. Such a simplification is valid for most MEMS devices and it makes the following data sampling procedure faster. The ultimate goal is to select the fewest possible number of modes to sufficiently characterize the deformation of the structure for the intended operating conditions. The fewer the modes, the shorter the time will be to generate the reduced order model.

- The Dmin and Dmax arguments of the RMMSELECT command are the lower and upper bounds of the total deflection range of the structure. They should be large enough to cover the operating range in the use pass.

### 6.2.9. Modify Modes for ROM

The automated mode selection performed by the RMMSELECT command may be manually changed or overridden. In some instances, specific knowledge of the device behavior and required modes may be already known, in which case you have the flexibility to select and modify the appropriate mode selection.

You can use the RMMRANGE command to define and edit the modal parameters.

Command(s): RMMRANGE
GUI: Main Menu> ROM Tool> Mode Selection> Edit

The following are important points to remember at this step:

- The computed displacement operating range for each mode can be modified by the Min and Max arguments of the RMMRANGE command. Note that if the mode was previously classified as "UNUSED" by either the RMMSELECT or the RMMRANGE commands, and you are issuing RMMRANGE to activate this mode for ROM, the Min and Max parameters will be interpreted as the total deflection range. Here, RMMRANGE will find the lower and upper bounds for the newly added mode, and calculate its contribution factor based on the information about all the active modes. If you disagree with the automatically calculated parameters for this mode, you can overwrite them by issuing RMMRANGE one more time.
• The $N_{step}$ argument of the RMMRANGE command specifies the number of equidistant steps for the coming data sampling procedure. Dominant modes should be sampled with 8 to 11 steps, relevant with 3 to 5. For three steps, the considered mode is linearized at the operating point.

• The default damping ratio is 0.05 for all modes. This number can be changed by the $Damp$ argument of the RMMRANGE command for any mode at any time (even in the use pass). Special consideration should be given to this damping parameter, as it represents the effects from fluidic damping of the structure.

• The $Scale$ argument of the RMMRANGE command is necessary to overcome convergence problems when computing the response surface. It should be:

$$Scale = \max\{\text{abs}(\text{Min}),\text{abs}(\text{Max})\}^{-1}$$

### 6.2.10. List Mode Specifications

You can use RMMLIST to call a status report at this point to check your mode specifications.

**Command(s):** RMMLIST  
**GUI:** Main Menu> ROM Tool> Mode Selection> List

### 6.2.11. Save ROM Database

At this point you should save your ROM database. The RMSAVE command saves it as an ASCII file. It will be used in the use pass and the expansion pass.

**Command(s):** RMSAVE  
**GUI:** Main Menu> ROM Tool> ROM Database> Save

### 6.2.12. Run Sample Point Generation

The next step is to run multiple finite element solutions on the structural domain and the electrostatic domain to collect sample points of strain energy and capacitance data for ROM response curve fitting. The model database must include the “STRU” and “ELEC” physics files and node components for the neutral plane nodes (“NEUN”) and conductors (“CONDi”) (see Section 6.1: Model Preparation). A ROM database is also required. The program performs the multiple finite element runs automatically with no user intervention.

**Command(s):** RMSMPLE  
**GUI:** Main Menu> ROM Tool> Sample Pt Gen> Compute Points

The following are important points to remember here:

• The number of finite element solution runs is dependent on the number of modes selected and the number of steps chosen to characterize each mode. A “finite element solution set” consists of a single structural analysis, and a set of electrostatic analyses, one for each conductor pair defined (see RMCAP command). For example, consider the following scenario of number of modes selected and number of steps specified:

  - Mode 1: Dominant; 8 steps specified
  - Mode 3: Dominant; 5 steps specified
  - Mode 5: Relevant; 3 steps specified

The total number of “finite element solution sets” would be $8 \times 5 \times 3 = 120$.

• The $N_{geom}$ flag must be set to ON in case of stress stiffening or prestress. Capacitance data can either be calculated from the charge voltage relationship ($Cap$ flag set to CHARGE) or from the derivatives of...
the electrostatic field energy based on the CMATRIX macro. The cap flag must be set to CMATRIX if far field elements are involved. The CMATRIX method is only recommended if significant electric field leakage occurs to the open domain, and capacitance effects of this leakage are significant.

- The results are stored in files called jobname_ijk.dec whereby a separate file is written for each relevant mode k. The files contain all the information necessary to evaluate the behavior of the relevant mode k with respect to the dominant modes i and j.

### 6.2.13. Specify Polynomial Order

In this step, you specify the polynomial orders for the modes that were selected for the ROM using RMMSELECT for use in function fitting the strain energy and capacitance data.

**Command(s):** RMPORDER  
**GUI:** Main Menu > ROM Tool > Resp Surface > Poly Order

Make sure that the order of each mode is less than $N_{steps}$ specified by RMMRANGE but at least two. Polynomials with order eight and higher tend to oscillate and should be avoided.

### 6.2.14. Define ROM Response Surface

In the run sample point generation step, the strain energy and capacitance data were computed at different linear combinations of all involved modal basis functions. In this step, you find mathematical functions that represent the dependency of the acquired data with respect to the modal coordinates. A least squares fit algorithm determines these mathematical functions. You can chose among four different polynomial trial functions, which are either inverted or not. The polynomials are later used to interpolate the energy and capacitance data between sample points and to compute their derivatives with respect to the modal coordinates to establish the system matrices.

**Command(s):** RMROPTIONS  
**GUI:** Main Menu > ROM Tool > Resp Surface > Options

Keep the following recommendations in mind:

- The argument Type = LAGRANGE is required if only one dominant mode or two dominant modes and no relevant modes are available. Otherwise try to use Type = PASCAL or even one of the reduced polynomials since those require fewer coefficients and enable essential speed up in the use pass.

- You should not invert strain energy functions. Capacitance functions should be inverted if the gap between conductors changes significantly during the operation. This happens for parallel plate arrangements where the conductors move perpendicularly to their surface. For comb drive systems, the capacitance function should not be inverted since conductors move tangentially to each other.

### 6.2.15. Perform Fitting Procedure

The next step is to perform a fitting procedure for all ROM functions based on modal data and functional data generated via RMSMIPLE and options defined by RMROPTIONS.

**Command(s):** RMRRGENERATE  
**GUI:** Main Menu > ROM Tool > Resp Surface > Fit Functions

Polynomial coefficients for the response surfaces are stored in files called jobname_ijk.pcs that correspond to the sample data file jobname_ijk.dec.
6.2.16. Plot Response Surface

Response surface plots help you verify that the fit functions to the expected behavior. If necessary, you can try different surface options to improve the fit results.

**Command(s):** RMRPLOT  
**GUI:** Main Menu > ROM Tool > Resp Surface > Plot

Response surface plots might also help you recognize oscillations. However, oscillations are usually not visible at the response surface itself but become obvious at the second derivative plots. To overcome oscillations, you should reduce the polynomial order or try another polynomial type. If both fail, you should increase the number of data points in the appropriate mode direction.

*Note* — Use the `/VIEW` command (Utility Menu > PlotCtrls > Pan-Zoom-Rotate) to reorient the plot view.

6.2.17. List Status of Response Surface

Next you should generate a status report that will help you assess the quality of the response surface.

**Command(s):** RMRSTATUS  
**GUI:** Main Menu > ROM Tool > Resp Surface > Status

6.2.18. Export ROM Model to External System Simulator

In this step, you may export the ROM model to an external VHDL-AMS compatible simulator. The export procedure creates the necessary files to run the ROM model in the system simulator.

**Command(s):** RMXPORT  
**GUI:** Main Menu > ROM Tool > Export > VHDL-AMS

Element loads are considered if an arbitrary scale factor was applied via RMLVSCALE prior to executing RMXPORT. RMXPORT generates a set of VDHL-AMS input files that contain the following:

- Problem specific constants (Initial.vhd)
- Strain energy functions (S_ams_ijk.vhd)
- Capacitance functions (Cxy_ams_ijk.vhd)
- ROM in VHDL language (Transducer.vhd)

*Note* — The VHDL-AMS transducer model is similar to a black-box model with terminals relating electrical and mechanical quantities. A further system description file is necessary to specify the external circuitry (voltage sources, controller units), structural loads (nodal forces, element loads) and run time parameters (time step size, total simulation time).

6.3. Use Pass

In the use pass, you run the ROM to obtain solutions of the coupled electrostatic-structural behavior of the device. The ROM is activated through the ROM144 element type. This element is a multiport element that may be used to perform multiple analysis simulation, including static, prestressed modal, prestressed harmonic or nonlinear transient analysis. The different analysis types are discussed in detail in the individual analysis guides. The use pass consists of the following steps.
The following sections describe each step.

6.3.1. Clear Database
6.3.2. Define a Jobname
6.3.3. Resume ROM Database
6.3.4. Define Element Type
6.3.5. Define Nodes
6.3.6. Activate ROM Database
6.3.7. Define Node Connectivity
6.3.8. Define Other Model Entities
6.3.9. Using Gap Elements with ROM144
6.3.10. Apply Loads
6.3.11. Specify Solution Options
6.3.12. Run ROM Use Pass
6.3.13. Review Results

6.3.1. Clear Database

At this point you should clear the database.

Command(s): /CLEAR
GUI: Utility Menu> File> Clear & Start New

6.3.2. Define a Jobname

Be sure to define a jobname that is different than the one used for the generation pass. For example, you could specify a jobname USE. This way, you can be sure that generation pass files from the modal analysis will not be overwritten.

Command(s): /FILNAME

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6.3.3. Resume ROM Database

The use pass is based on the reduced order model. Therefore, you must resume the ROM specifications. Only one ROM database may be active for a use pass.

Command(s): RMRESUME
GUI: Main Menu> ROM Tool> ROM Database> Resume

6.3.4. Define Element Type

You then define the ROM element (ROM144) as one of the element types. Set KEYOPT(1) to one if master nodes should be considered for the use pass.

Command(s): ET
GUI: Main Menu> Preprocessor> Element Type> Add/Edit/Delete

The ANSYS Circuit Builder (see Chapter 15, “Electric Circuit Analysis” in ANSYS Low-Frequency Electromagnetic Analysis Guide) provides a convenient tool for constructing the ROM144 element and any attached linear circuit elements (CIRCU124), mechanical spring, mass, and damper elements (COMBIN14, MASS21, and COMBIN39), or the electromechanical transducer element (TRANS126).

ROM144 fully couples the electrostatic and structural domains. It is defined by twenty (KEYOPT(1) = 0) or thirty nodes (KEYOPT(1) = 1):

- Nodes 1 to 10 are modal ports and relate modal amplitudes (EMF degree of freedom) to modal forces. The node numbers represent the numbers of the involved modes from the ROM database. For example, if modes 1, 3, and 5 are used in the ROM database, the modal amplitudes of modes 1, 3, and 5 are mapped to nodes 1, 2, and 3 respectively. Modal displacements can be set to zero to deactivate modes.

  Note — Only the first 9 nodes may be used for modal amplitude degrees of freedom.

- Nodes 11 to 20 are electrical conductor ports and relate voltage (VOLT degree of freedom) to current. Node 11 represents the first conductor, node 12 represents the second conductor, and so on. Current can only be imposed in a harmonic or transient analysis.

  Note — Only the first 5 ports can be used.

- Nodes 21 to 30 are nodal ports relating displacements (UX degree of freedom) to forces at master nodes. Node 21 represents the first defined master node, node 22 represents the second master node, and so on. Master displacements and forces are always mapped to the UX degree of freedom and FX force label independent from their real DOF direction. Node to node contact or spring damper elements (COMBIN14, COMBIN40) can be directly attached to the UX degree of freedom at master nodes. Only elements that have a single UX degree of freedom may be used at a displacement port.

See the ANSYS Elements Reference for more detailed information on this element.

6.3.5. Define Nodes

You then define nodes for ROM144. If KEYOPT(1) is zero, 20 nodes must be defined. Otherwise, define 30 nodes.

Use the circuit builder or one of the following:

Command(s): N
GUI: Main Menu> Preprocessor> Modeling> Create> Nodes> In Active CS
6.3.6. Activate ROM Database

The next step is to activate the ROM database for the use pass.

Command(s): RMUSE
GUI: Main Menu> Preprocessor> Loads> Analysis Type> Analysis Options

6.3.7. Define Node Connectivity

In this step, you define the node connectivity of the ROM144 element. Use the Circuit Builder or one of the following:

Command(s): E, EMORE
GUI: Main Menu> Preprocessor> Modeling> Create> Elements> Thru Nodes

You need to issue the E command once for the first eight nodes and the EMORE command two (KEYOPT(1) = 0) or three (KEYOPT(1) = 1) times to define the other nodes for the ROM144 element.

6.3.8. Define Other Model Entities

You then define other elements attached to the ROM144 element with the Circuit Builder as shown in Figure 6.5: “ROM144 and Attached Elements” and exit the preprocessor. If the desired 1-D element is not supported in the circuit builder, it may be defined manually (for example, COMBIN40).

Command(s): ET, FINISH
GUI: Main Menu> Preprocessor> Element Type> Add/Edit/Delete
Main Menu> Finish

Figure 6.5 ROM144 and Attached Elements
6.3.9. Using Gap Elements with ROM144

If you intend to operate the ROM144 element at voltage levels that exceed the "pull-in" voltage (voltage level at which the device snaps down onto the conductor), the element will not converge unless gap elements constrain the active modal amplitude degrees of freedom (EMF). The following guidelines are recommended.

- Create COMBIN40 elements for active EMF degrees of freedom.
- Use the UX degree of freedom option on the COMBIN40 element.
- Create the I and J nodes of the COMBIN40 element at the same location (coincident) as the modal amplitude (EMF) degree of freedom.
- Use an appropriate gap stiffness. 1E5 is suggested for most MEMS applications.
- Set the gap distance equal to the lower or upper bound displacement of the mode as computed from the RMMSELECT command (whichever is greater).
- Set the displacement of node I of the gap element to zero.
- Use a constraint equation to enforce equivalent displacement of the J node of the gap element (UX degree of freedom) to the modal amplitude (EMF) degree of freedom. For example, if the modal amplitude DOF is node "2", and the J node of the gap element is node 42, and the constraint equation is number 2, then the constrain equation would be: CE,2,0,42,ux,1,2,emf,-1.

By using gap elements, you should be able to ramp your applied voltage or displacement loads and successfully pass through the pull-in voltage. You may need to increase the number of equilibrium iterations through the NEQIT command to several hundred in order to achieve a converged solution. You can monitor the gap status of the gap elements to see when the pull-in occurs. The DCVSWP command macro utilizes gap elements in order to pass through the pull-in voltage.

6.3.10. Apply Loads

You now apply loads. ROM144 supports the loads summarized in the following table.

Table 6.1 ROM144 Loads

<table>
<thead>
<tr>
<th>Load Type</th>
<th>DOF</th>
<th>Node Numbers</th>
<th>Command</th>
</tr>
</thead>
<tbody>
<tr>
<td>Modal Amplitude</td>
<td>EMF</td>
<td>1–10</td>
<td>D</td>
</tr>
<tr>
<td>Voltage</td>
<td>VOLT</td>
<td>11–20</td>
<td>D</td>
</tr>
<tr>
<td>Current</td>
<td>AMPS</td>
<td>11–20</td>
<td>F</td>
</tr>
<tr>
<td>Nodal Displacement</td>
<td>UX</td>
<td>21–30</td>
<td>D</td>
</tr>
<tr>
<td>Nodal Force</td>
<td>FX</td>
<td>21–30</td>
<td>F</td>
</tr>
</tbody>
</table>

For convenience, a command macro DCVSWP has been created to execute a static analysis that is commonly performed. You can perform a DC voltage sweep up to a defined maximum voltage or up to a “pull-in” value. All conductors are set to ground except the sweep conductor.

Command(s): DCVSWP
GUI: Main Menu> Solution> ROM Tools> Voltage Sweep

Of course, you can specify an arbitrary analysis with complete arbitrary loading.
6.3.11. Specify Solution Options

All solution options described in the ANSYS Structural Analysis Guide are valid for the ROM use pass. Some recommendations are:

- Set the modal force (label CURT) convergence parameter of CNVTOL to roughly 1E-6. Accuracy may depend on the value of this convergence parameter.
- Coupled electromechanical systems are, in general, nonlinear. Nevertheless, you can perform a prestressed modal or harmonic analysis for any static equilibrium state obtained with the application of structural or electrostatic loads. Keep in mind that all system parameters are linearized as known from a small signal analysis. Activate PSTRES and perform a static analysis prior to the modal or harmonic analysis.
- You can use a prestress modal analysis to calculate the frequency shift due to stress stiffening or electrostatic softening. To run a modal analysis, activate the symmetric matrix option by setting KEYOPT(2) = 2 for the ROM element.
- For a transient analysis, set the Newton-Raphson option to FULL (NROPT,FULL).

Usually the structural domain reacts with twice the frequency of the driving sinusoidal voltage time function. This is because electrostatic forces are quadratic functions of voltage. A harmonic response analysis is only applicable if the polarization voltage in the preceding static analysis is much higher than the alternating voltage in the harmonic analysis.

A ROM solution will generate a reduced displacement results file (filename.rdsp).

6.3.12. Run ROM Use Pass

You then run the ROM use pass and exit the solution processor.

Command(s): SOLVE, FINISH
GUI: Main Menu> Preprocessor> Element Type> Add/Edit/Delete
      Main Menu> Finish

6.3.13. Review Results

Review use pass results with POST1 and POST26. Results include modal amplitudes (EMF), conductor voltages (VOLT), nodal displacements (UX), and reaction solutions (AMPS, FX).

6.4. Expansion Pass

The expansion pass starts with the results of the use pass and expands the reduced solution to the full DOF set for the structural domain in the model database. The figure below shows the data flow between the generation pass, use pass, and expansion pass. As shown, the expansion pass requires files from the generation pass and the use pass.
Caution: For a stress-stiffened structure, although the deflection results on the neutral plane are correct, the element results such as stress and strain are typically slightly higher than the true values. The linear expansion pass procedure cannot capture correctly the nonlinear deviations of nodes on the outer planes of the structures.

The expansion pass consists of the following steps.

6.4.1. Clear Database
6.4.2. Define a Jobname
6.4.3. Resume ROM
6.4.4. Resume Model Database
6.4.5. Activate ROM Database
6.4.6. Perform Expansion Pass
6.4.7. Review Results
The following sections describe each step.

6.4.1. Clear Database

At this point you should clear the use pass database.

Command(s): /CLEAR
GUI: Utility Menu> File> Clear & Start New

6.4.2. Define a Jobname

Change the jobname to what is was during the generation pass (for example, GEN).

Command(s): /FILNAME
GUI: Utility Menu> File> Change Jobname

6.4.3. Resume ROM

You must resume the ROM file (for example, GEN.rom).

Command(s): RMRESUME
GUI: Main Menu> ROM Tool> ROM Database> Resume

6.4.4. Resume Model Database

You must also resume the model database (for example MODEL.db).

Command(s): RESUME
GUI: Utility Menu> File> Resume from

6.4.5. Activate ROM Database

Next, you need to activate the ROM database by setting the RMUSE Option field to ON. You also need to set the Usefil field to the name of the reduced displacement file (.rdsp) created in the use pass.

Command(s): RMUSE
GUI: Main Menu> Solution> Analysis Type> Analysis Options
6.4.6. Perform Expansion Pass

In this step, you expand the reduced solution to the full DOF set.

Command(s): EXPASS, EXPSOL
GUI: Main Menu> Solution> Analysis Type> ExpansionPass
      Main Menu> Solution> Load Step Opts> ExpansionPass> By Load Step (or By Time/Freq)

6.4.7. Review Results

You can review expansion pass results with POST1 and POST26. For a complete description of all postprocessing functions, see the ANSYS Basic Analysis Guide.

6.5. Sample Miniature Clamped-Clamped Beam Analysis (Batch or Command Method)

6.5.1. Problem Description

Miniature clamped-clamped beams with dimensions in the micrometer range are widely used in MEMS. Typical examples are resonators for RF filters, voltage controlled micro switches, adjustable optical grating or test structures for material parameter extraction. Clamped-clamped beams can behave in a highly nonlinear fashion due to deflection dependent stiffening and stiffening caused by prestress. Both effects are very important for MEMS analysis and are illustrated by the following example.

Figure 6.8 Clamped-Clamped Beam with Fixed Ground Conductor

The half symmetry model uses hexahedral solid elements (SOLID45) for the structural domain and tetrahedral elements (SOLID122) for the electrostatic domain. The beam is fixed on both ends and symmetry boundary conditions are applied on the plane of intersection. The deflection to beam thickness ratio is more than 1 in order to realize essential stiffness change due to the stress stiffening effect.
This example demonstrates nonlinear effects. First, the beam is considered as linear. The stress stiffening option is OFF. In the next case, stress stiffening is ON to model the real behavior. Finally, a 100 kPa biaxial prestress is applied. Initial prestress is modeled via thermal expansion in order to realize a nonuniform stress distribution at the clamp. Note that the uniaxial stress in the beam is different from the biaxial stress of the layer prior to release etching. The Generation Pass must be performed three times.

### 6.5.2. Program Listings

The following command input corresponds to the last case of a structure with initial prestress. Set **TUNIF** to zero in this file if initial prestress is not considered.

**Model Input File:**

```plaintext
/filnam,cbeam
/PREP7, Clamped-clamped beam with fixed ground electrode

! µMKSV system of units

! Model parameters

B_L=100             ! Beam length
B_W=20              ! Beam width
B_T=2               ! Beam thickness
F_L=4               ! Farfield in beam direction
F_Q=4               ! Farfield in cross direction
F_O=4               ! Farfield above beam
E_G=4               ! Electrode gap

sigm_b=-100

/VIEW,1,1,,-1,1
/PNUM,TYPE,1
/NUMBER,1
/PBC,ALL,1

/PREP7

ET,1,SOLID45         ! Structural domain
ET,2,SOLID122        ! Electrostatic domain
```
Section 6.5: Sample Miniature Clamped-Clamped Beam Analysis (Batch or Command Method)

EMUNIT, EPZRO, 8.85e-6 ! Free space permittivity
MP, PERX, Z, 1 ! Relative permittivity of air
! Half symmetry
BLOCK, 0, B_L, 0, B_W/2+F_Q, -E_G, B_T+F_O ! Entire domain
BLOCK, 0, B_L, 0, B_W/2, 0, B_T ! Structural domain
BLOCK, 0, B_L, 0, B_W/2, -E_G, 0
VOVLAP, ALL

LSEL, S, LOC, X, B_L/2 ! Mesh density in axial direction
LESIZE, ALL, 20, 1
LSEL, S, LOC, Y, B_W/4 ! Mesh density in transverse direction
LESIZE, ALL, 2, 1
LSEL, S, LOC, Z, B_T/2 ! Mesh density in vertical direction
LESIZE, ALL, 2, 1
LSEL, ALL
VSEL, S, LOC, Z, B_T/2 ! Mesh structural domain (mapped meshing)
VMESH, ALL
VSEL, ALL

SMRTSIZ, 2
MSHAPE, 1, 3D
MSHKEY, 0
TYPE, 2
MAT, 2
VMESH, 4

LSEL, S, LOC, Y, b_w/2+f_q ! Mesh density at bottom electrode
LSEL, R, LOC, x, b_l/2
LESIZE, ALL, 19, 1
LSEL, S, LOC, Y, 0 ! Mesh density at bottom electrode
LSEL, R, LOC, Z, b_t+f_o
LESIZE, ALL, 19, 1
LSEL, S, LOC, Y, (b_w+f_q)/2
LESIZE, ALL, 4, 1/5, 1
LSEL, ALL
VMESH, ALL

VSEL, S, LOC, Z, b_t/2 ! Movable electrode
ASLV, S, 1
ASEL, U, LOC, Y, 0
ASEL, U, LOC, X, 0
ASEL, U, LOC, X, B_L
NSLA, S, 1
CM, COND1A, AREA
CM, COND1, NODE ! Conductor 1 node component
ALLSEL
ASEL, S, LOC, Z, -e_g ! Fixed ground electrode
NSLA, S, 1
CM, COND2A, AREA
CM, COND2, NODE ! Conductor 2 node component
ALLSEL
VSEL, U, LOC, Z, b_t/2 ! Region for DVMORPH
CM, AIR, VOLU ! Default name 'AIR'
VSEL, ALL

ESEL, S, MAT, 1
NSEL, S, 1
NSEL, R, LOC, Z, b_t/2
CM, NEUN, NODE ! Neutral plane node component
ALLSEL

ET, 1, 0

PHYSICS, WRITE, ELECTRIC ! Write electrostatic physics file
PHYSICS, CLEAR

ET, 1, SOLID45
ET, 2, 0
Chapter 6: Reduced Order Modeling

MP,EX,1,169e3 ! Material properties Si
MP,NUXY,1,0.066 ! <110>
MP,DENS,1,2.329e-15
MP,ALPX,1,1e-6

ASEL,S,LOC,Z,b_t/2
ASEL,R,LOC,Y,b_w/4

ctime,S,1
CM,FXA,AREA
DA,ALL,UX ! Boundary condition must be
DA,ALL,UY ! applied on solid model entities
DA,ALL,UZ

ASEL,S,LOC,Z,b_t/2
ASEL,R,LOC,Y,0

CM,BCYA,AREA
DA,ALL,UY

ALLSEL

/NSLA,S,1

CM,FIXA,AREA

/DA,ALL,UX

/DA,ALL,UY

/DA,ALL,UZ

ASEL,S,LOC,Z,b_t/2
ASEL,R,LOC,Y,b_w/4

NSLA,S,1

CM,FXA,AREA

DA,ALL,UX

/DA,ALL,UY

/DA,ALL,UZ

ASEL,S,LOC,Z,b_t/2
ASEL,R,LOC,Y,0

NSLA,S,1

CM,BCYA,AREA

DA,ALL,UY

ALLSEL

Fini

/PhysicS,write,STRU ! Write structural physics file

ET,2,SOLID122 ! Plot the entire model

Eplot

Save ! Save model database

Generation Pass:

No test load is defined. Hence the first modes in the operating direction will be used. There are two element loads: acceleration and a uniform pressure load. For initial prestress NLGEOM must be set ON and the loads must cause moderate displacements (in the range of 0.001 to 0.1 times the beam thickness).

/filnam,gener ! Jobname for the Generation Pass

rmanl,cbeam,db,,3,z ! Assign model database, dimensionality, oper. direction

resu,cbeam,db ! Resume model database

rmcap,cap12,1,2 ! Define capacitance

rmclist ! List capacitances

rmaster,node(b_l/2,0,0) ! Define master nodes

rmaster,node(b_l/4,0,0)

! Apply element loads

Physics,clear

Physics,read,STRU

/solu

antype,static

nlgeom,0n

acel,,,9.81e12 ! Acceleration in Z-direction 9.81e6 m/s**2

lswrite,1

acel,0,0,0

esel,s,type,,1

nsle,s,1

nsel,r,loc,z,0

sf,all,pres,0.1

100 kPa

allsel

lswrite,2

lssolve,1,2

fini
Use Pass:

Calculation of voltage displacement functions up to pull-in

The following input was used for all three cases.

! *** Calculation of voltage displacement functions up to pull-in
/clear
/[filnam,use1
/rmresu,cbeam,rom

ET,1,144

Section 6.5: Sample Miniature Clamped-Clamped Beam Analysis (Batch or Command Method)
The pull-in results for the three cases are as follows:

- Linear analysis: 992 volts
- Nonlinear analysis (stress stiffening is ON): 1270 volts
- Initial prestress analysis: 1408 volts

**Connecting other elements to ROM144**

The structure is driven by a voltage sweep to the contact pad placed at the center of the micro beam. A gap element (COMBIN40) connects to the center of the beam at a master node (node 21). It has a contact stiffness of 1.6E6 N/m and an initial gap of 0.3 µm. The UX degree of freedom tracks the master node displacement (actual displacement is in the Z-direction). Similar models can simulate voltage controlled micro switches.
6.6. Sample Micro Mirror Analysis (Batch or Command Method)

6.6.1. Problem Description

The micro mirror problem demonstrates the reduced order modeling procedure of an electrostatically actuated MEMS with multiple electrodes. The micro mirror cell is part of a complex mirror array used for light deflection applications. The entire mirror array consists of six separate mirror strips driven synchronously in order to achieve high-speed light deflection. Each strip is attached to the wafer surface by two intermediate anchor posts. Due to the geometrical symmetry, the mirror strips can be divided into three parts whereby just one section is necessary for finite element analyses.

Figure 6.10 Schematic View of a Micro Mirror Array and a Single Mirror Cell

The electrostatic domain consists of three conductors, where the nodes of the mirror itself are defined by node component COND1, and the fixed ground conductors are node components COND2 and COND3. The fixed conductors are on top of the ground plate shown in Figure 6.10: “Schematic View of a Micro Mirror Array and a Single Mirror Cell” and Figure 6.11: “Parameter Set for Geometrical Dimensions of the Mirror Cell”.

The model uses hexahedral solid elements (SOLID45) for the structural domain and tetrahedral elements (SOLID122) for the electrostatic domain.
6.6.2. Program Listings

Model Input File:

```
/TITLE, Silicon micro mirror cell
/filename, mirror

/ PREP7

fe_la=200                        ! Spring length
fe_br=10                         ! Spring width
fe_di=15                         ! Spring thickness
sp_la=1000                       ! Mirror length
sp_br=250                        ! Mirror width
mi_la=520                        ! Length center part
mi_br=35                         ! Width center part
po_la=80                         ! Length of anchor post
po_br=80                         ! Width of anchor post
fr_br=30                         ! Fringing field distance
d_ele=20                         ! Electrode gap

ET, 1, SOLID45                    ! Structural domain
ET, 2, SOLID122                   ! Electrostatic domain

EMUNIT, EPZRO, 8.85e-6            ! Free space permittivity
MP, PERX, 2, 1                   ! Relative permittivity of air

del1=(mi_br-fe_br)/2

K, 1                             
K, 2,, fe_br/2
K, 3,, mi_br/2
K, 4,, po_br/2+(mi_br-fe_br)/2
K, 5,, sp_br/2
K, 6,, sp_br/2+fr_br

KGEN, 2, 1, 6, 1, mi_la/2
KGEN, 2, 1, 6, 1, mi_la/2+fe_la-(mi_br-fe_br)/2
KGEN, 2, 1, 6, 1, sp_la/2
K, 21, sp_la/2, po_br/2
K, 13, sp_la/2-po_la/2
K, 14, sp_la/2-pa_la/2, fe_br/2
K, 25, sp_la/2-po_la/2, po_br/2

A, 3, 9, 10, 4
```
Section 6.6: Sample Micro Mirror Analysis (Batch or Command Method)

A, 9, 15, 16, 10
A, 4, 10, 11, 5
A, 10, 16, 17, 11
A, 16, 22, 23, 17
AGEN, 2, ALL, , , , "-d_ele"
ASEL, S, LOC, Z, "-d_ele"
ADD, ALL
ASEL, ALL
A, 1, 7, 8, 2
A, 2, 8, 9, 3
A, 7, 13, 14, 8
A, 13, 19, 20, 14
A, 14, 20, 21, 25
ASEL, S, LOC, Z, 0
VEXT, ALL, , , , "fe_di"
ASEL, ALL
ASEL, S, AREA, , 9, 10
VEXT, ALL, , , , "-d_ele"
ASEL, ALL
VATT, 1, 1
BLOCK, 0, sp_la/2, o, sp_br/2+fr_br, "-d_ele", "fe_di"
VDELE, 13
AOVLAP, ALL
ASEL, S, LOC, Z, "fe_di"
ASEL, A, LOC, Z, "-d_ele"
ASEL, A, LOC, X, 0
ASEL, A, LOC, X, sp_la/2
ASEL, A, LOC, Y, 0
ASEL, A, LOC, Y, sp_br/2+fr_br
VA, ALL
VSEL, S, VOLU, 14
VATT, 2, 2
VSEL, ALL
ESIZE, 2
LESIZE, 68, 1, 1
LESIZE, 77, 10, 1
LESIZE, 67, 5, 1
LESIZE, 82, 2, 1
LESIZE, 51, 5, 1
LESIZE, 62, 2, 1
LESIZE, 87, 2, 1
LESIZE, 75, 1, 1
LESIZE, 42, 1, 1
LESIZE, 54, 3, 1
! Y-direction
VMESH, 1, 1, 12
TYPE, 2
MAT, 2
SMRTSZ, 2
MSHAPE, 1, 3D
MSHKEY, 0
ESIZE, 1
VMESH, 14
ALLSEL
VSYM, x, all
VSYM, y, all
NUMMRG, node, 1e-5
NUMMRG, kp, 1e-3
VSEL,s,type,,1
ASEL,s,ext
ASEL,u,loc,x,sp_la/2
ASEL,u,loc,x,-sp_la/2
ASEL,u,loc,z,fe_di
ASEL,u,loc,z,-d_ele
NSLA,S,1
CM,COND1A,AREA         ! Mirror electrode
CM,COND1,NODE
ALLSEL
ASEL,s,area,,11
ASEL,a,area,,128
NSLA,S,1
CM,COND2A,AREA         ! First fixed electrode
CM,COND2,NODE
ALLSEL
ASEL,s,area,,202
ASEL,a,area,,264
NSLA,S,1
CM,COND3A,AREA         ! Second fixed electrode
CM,COND3,NODE
ALLSEL
VSEL,s,type,,2
CM,AIR,VOLU         ! Region to be morphed
VSEL,ALL
ESEL,S,MAT,,1         ! Define neutral plane
NSLE,S,1
NSEL,R,LOC,Z,fe_di/2
CM,NEUN,NODE
ALLSEL
ET,1,0
PHYSICS,WRITE,ELEC     ! Write electrostatic physics file
PHYSICS,CLEAR
ET,1,SOLID45
ET,2,0
MP,EX,1,169e3         ! Material properties of Si
MP,NUXY,1,0.066
MP,DENS,1,2.329e-15
VSEL,s,type,,1
ASLV,s,1
ASEL,r,loc,z,-d_ele
NSLA,S,1
CM,FIXA,AREA         ! Boundary condition must be
DA,ALL,UX
DA,ALL,UY
DA,ALL,UZ
! applied on solid model entities
! Fixed boundary condition
ASLV,S,1
ASEL,R,LOC,X,sp_la/2
DA,ALL,UX
NSLA,S,1
! Symmetry boundary conditions
ASLV,S,1
ASEL,R,LOC,X,-sp_la/2
DA,ALL,UX
NSLA,A,1
CM,SYMB,C,NODE
ALLSEL
PHYSICS,WRITE,STRU     ! Write structural physics file
ET,2,SOLID122
EPLT
FINI
SAVE ! Save model database

**Generation Pass:**

The following Generation Pass considers the first two of three modes: torsion mode, transversal mode in Z-direction and one mode responsible for plate warp. In addition to the capacitances between movable and fixed conductors CAP12 and CAP13, you should activate CAP23, which affects the mirror behavior in case of high polarization voltages. The total deflection range is 75% of the electrode gap.

A test load computes an approximate deflection state of the mirror for use in selecting the above modes. The test load contains two uniform pressure loads equivalent to the electrostatic pressure at the initial position.

Element loads are acceleration of 9.81 m/s² in Z-direction and a uniform 1 MPa pressure load acting on the upper mirror wing

```plaintext
/filename,gener                       ! Specify jobname for Generation Pass
rmanl,mirror,db,,3,z                 ! Assign model database, dimensionality, oper. direction
resu,mirror,db                        ! Resume model database

! Apply element loads
physics,clear
physics,read,STRU                   ! Read structural physics file
/view,1,-1
/pbc,all,1
/solu
antype,static
nlgeom,off

acel,,,9.81e6                           ! Acceleration in z-direction
lswrite,1

acel,0,0,0
esel,s,type,,1
nsle,s,1
nsel,r,loc,z,0
nsel,r,loc,y,0,sp_br/2
sf,all,pres,1                             ! Uniform pressure load on the upper mirror wing
allsel
lswrite,2
lssolve,1,2
fini

/post1                                 ! Extract neutral plane displacements
set,1                                   ! due to the element load
rmndisp,'eload','write'
set,2
rmndisp,'eload','append'
fini

! Apply test load
physics,clear
physics,read,STRU

u_test=150                                ! Voltage applied on COND1
u_pol=400                                 ! Polarization voltage applied on COND2 and COND3

/solu
pres1=8.85e-6*(u_pol-u_test)**2/(2*d_ele**2)
pres2=8.85e-6*(u_pol+u_test)**2/(2*d_ele**2)
```

**Section 6.6: Sample Micro Mirror Analysis (Batch or Command Method)**

---

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esel,s,type,,1  
nsls,s,1  
nsel,r,loc,z,0  
nsel,r,loc,y,mi_br/2,sp_br/2  
sf,all,pres,-pres1  
allsel  
esel,s,type,,1  
nsls,s,1  
nsel,r,loc,z,0  
nsel,r,loc,y,-sp_br/2,-mi_br/2  
sf,all,pres,-pres2  
allsel  
solve  
fini

/post1
set, last  
rmndisp,'tload'  
fini

rmcap,cap12,1,2  
rmcap,cap13,1,3  
rmcap,cap23,2,3  

mn1=node(0.0000,125.00,7.5000)  ! Define master nodes  
mn2=node(0.0000,0.0000,7.5000)  
mn3=node(169.00,-104.29,0.0000)  

rmaster,mn1  ! Upper node on center line  
rmaster,mn2  ! Middle node on center line  
rmaster,mn3  ! Lower node on center line  
rmalist  

physics, clear  
physics, read, STRU

/solu
antype,modal  
modopt,lanb,6  
mxpand,6  
solve  
fini

/post1
rmnevec  ! Extract modal displacements at  
normal plane nodes  
fini

rmmselect,3,'tmod',-15,15  ! Automated mode selection  
rmmlist  

rmmrange,1,'DOMINANT',,,6,0.05  ! use 6 steps for mode 1  
rmmrange,3,'DOMINANT',,,5,0.05  ! use 5 steps for mode 3  
rmmrange,5,'UNUSED'  ! do not use mode 5  

rmsave,mirror,rom  ! Save ROM database  

rmsample  ! Generate samples points and run FE analyses  
            ! to calculate strain energy and capacitances  

rmmporder,4,,3  ! Define polynomial orders for response surface  
rmroption,sene,lagrange,0  
rmroption,cap12,lagrange,1  
rmroption,cap13,lagrange,1  
rmroption,cap23,lagrange,1  

rmrgenerate  ! Generate Response Surface
The response surfaces are fitted with Lagrange polynomials whereby the capacitance functions are inverted. Polynomial orders are four and three, which requires 20 polynomial coefficients for each response surface. A further reduction is possible. The result file gen_130.dec contains all FE sample data and gen_130.pcs the polynomial information.

**Calculation of voltage displacement functions up to pull-in**

```
! *** Voltage displacement function up to pull in
! *** A voltage sweep is applied in COND2

/clear
/filnam,use1
rmresu,mirror,rom ! Resume ROM database
/PREP7
ET,1,144,1 ! Define ROM element type
*do,i,1,30
   n,i
*endo
rmuse,on ! Activate ROM use pass
 e,1,2,3,4,5,6,7,8
 emore,9,10,11,12,13,14,15,16
 emore,17,18,19,20,21,22,23,24
 emore,25,26,27,28,29,30
FINISH
/gst,off
! Compute voltage sweep up to pull-in,
! Sweep conductor is COND2
! Start an equidistant voltage sweep up to 800 V by a voltage increment of 10 V
! Increase voltage beyond 800 up to pull-in with accuracy of 1 Volt
! Create gap elements to converge at pull-in

DCVSWP,'pi',1,2,800,10,1
DCVSWP,'gv',1,2,859,10,,1
/post26
/axlab,x,Voltage
/axlab,y,Modal amplitudes
nsol,2,1,emf,,mode1 ! Torsion mode
nsol,3,2,emf,,mode3 ! Transversal mode
nsol,4,12,volt,,voltage ! Applied voltage
xvar,4
plvar,2,3 ! Modal displacements
/axlab,y,Modal displacements
nsol,6,21,ux,,up_edge ! Node on the upper edge
nsol,7,22,ux,,center_n ! Node at plate center
nsol,8,23,ux,,lo_edge ! Node at the lower edge
plvar,6,7,8
fini
```

The computed pull-in voltage is 859 volts.
The modal amplitude and master displacements as functions of voltage are shown in Figure 6.12: “Modal Amplitudes vs. Voltage” and Figure 6.13: “Master Displacements vs. Voltage”.

**Figure 6.12 Modal Amplitudes vs. Voltage**

**Figure 6.13 Master Displacements vs. Voltage**

**Calculation of voltage displacement functions at multiple load steps**

```plaintext
! *** Calculate voltage displacement functions at multiple load steps
! *** A voltage sweep is applied to COND1
! *** COND2 and COND3 carry a fixed polarization voltage

/clear
/fname,use2

rmresu,mirror,rom

/Prep7
ET,1,144

*do,i,1,20
n,i
*enddo
```
High polarization voltages of opposite sign (±800V) are applied on both fixed electrodes. The varying driving voltage is applied on the entire mirror structure. A positive voltage tilts the mirror to the right and a negative voltage to the left. The voltage stroke function of mode 1 is strongly linearized in the operating range between -60 and 60 Volt (Figure 6.14: “Modal Amplitude of Mode 1 vs. High Polarization Voltage”). The voltage stroke function of the transversal mode is shown in Figure 6.15: “Modal Amplitude of Mode 3 vs. High Polarization Voltage”. Both negative and positive voltages increase the transversal amplitude.
Figure 6.14 Modal Amplitude of Mode 1 vs. High Polarization Voltage
Figure 6.15 Modal Amplitude of Mode 3 vs. High Polarization Voltage

Calculated capacitances are shown in the following figures.
Figure 6.16 Capacitances CAP12 and CAP13 vs. High Polarization Voltage
Figure 6.17 Capacitance CAP23 vs. High Polarization Voltage

Calculation of displacements at acting element loads

! *** Calculate deflection state at acting element loads

/clear
/filnam,use3
rmresu,mirror,rom
/PREP7
ET,1,144,1
*do,i,1,30
  n,i
  *enddo
 rmuse,on
 e,1,2,3,4,5,6,7,8
 emore,9,10,11,12,13,14,15,16
 emore,17,18,19,20,21,22,23,24
 emore,25,26,27,28,29,30
FINISH
/gst,off
/solu
An acceleration of 9.81 m/s² and a uniform pressure load of 10 kPa were applied to the upper mirror wing. Computed displacements at the expansion pass are shown in Figure 6.18: “Expanded Displacements for Acceleration Load” and Figure 6.19: “Expanded Displacements for Pressure Load”.

```plaintext
antyp, static
outres, all, all
cnvto1, curt, 1.0d-6, 2

d, 11, volt, 0
d, 12, volt, 0
d, 13, volt, 0
outres, all, all
rmivscale, 2, 1, 0
solve

rmivscale, 2, 0, -0.01
solve
fini

/post1
set, 1
prdisp
set, 2
prdisp
fini

! Start expansion pass

/clear
/filnam, gener
resu, mirror, db
rmre, mirror, rom

physics, clear
physics, read, STRU

/solu
rmuse, on, use3
expass, on
expsol,,,, ON
solve
fini

/post1
set, 1
plnsol, u, z, 2
set, 2
plnsol, u, z, 2
fini
```

An acceleration of 9.81 m/s² and a uniform pressure load of 10 kPa were applied to the upper mirror wing. Computed displacements at the expansion pass are shown in Figure 6.18: “Expanded Displacements for Acceleration Load” and Figure 6.19: “Expanded Displacements for Pressure Load”.

```plaintext
antyp, static
outres, all, all
cnvto1, curt, 1.0d-6, 2

d, 11, volt, 0
d, 12, volt, 0
d, 13, volt, 0
outres, all, all
rmivscale, 2, 1, 0
solve

rmivscale, 2, 0, -0.01
solve
fini
```

An acceleration of 9.81 m/s² and a uniform pressure load of 10 kPa were applied to the upper mirror wing. Computed displacements at the expansion pass are shown in Figure 6.18: “Expanded Displacements for Acceleration Load” and Figure 6.19: “Expanded Displacements for Pressure Load”.

```plaintext
antyp, static
outres, all, all
cnvto1, curt, 1.0d-6, 2

d, 11, volt, 0
d, 12, volt, 0
d, 13, volt, 0
outres, all, all
rmivscale, 2, 1, 0
solve

rmivscale, 2, 0, -0.01
solve
fini
```

An acceleration of 9.81 m/s² and a uniform pressure load of 10 kPa were applied to the upper mirror wing. Computed displacements at the expansion pass are shown in Figure 6.18: “Expanded Displacements for Acceleration Load” and Figure 6.19: “Expanded Displacements for Pressure Load”.

```plaintext
antyp, static
outres, all, all
cnvto1, curt, 1.0d-6, 2

d, 11, volt, 0
d, 12, volt, 0
d, 13, volt, 0
outres, all, all
rmivscale, 2, 1, 0
solve

rmivscale, 2, 0, -0.01
solve
fini
```
Figure 6.18 Expanded Displacements for Acceleration Load

NODAL SOLUTION
STEP = 1
ST = 1
TIME = 1
UE (AVG)
RYS = 0
DMX = .764E-04
SMN = -.764E-04
SHE = .437E-07
Figure 6.19  Expanded Displacements for Pressure Load

The following example demonstrates the change of harmonic transfer functions at different polarization voltages. The higher the applied polarization voltage, the more the resonance peak shifts to the left.

! *** Prestressed harmonic analysis

/clear
/filename,use4
rmresu,mirror,rom

/PREP7
ET,1,144,1
*do,i,1,30
n,i
*enddo
rmuse,on
e,1,2,3,4,5,6,7,8
emore,9,10,11,12,13,14,15,16
emore,17,18,19,20,21,22,23,24
emore,25,26,27,28,29,30
FINISH

/gst,off

/solu
antyp,static
outres,all,all
cnvtol,curt,1.0d-6,,2
pstress,on
d,11,volt,0
d,12,volt,800
d,13,volt,-800
solve
fini

/solu
antype,harmonic
pstress, on
harfrq,0,5e4
nsubet,100
kbc,1
d,11,volt,1
d,12,volt,0
d,13,volt,0
solve
fini

/post26
/axlab,x,Frequency
/axlab,y,Modal Amplitude
nsol,2,1,emf,,model
plvar,2
/axlab,y,Nodal amplitude
nsol,3,21,ux,,up_edge
nsol,4,23,ux,,lo_edge
plvar,3,4
/axlab,y,Phase angle
plcplx,1
plvar,3,4
fini

Figure 6.20 Harmonic Transfer Function Amplitude for 800 V Polarization Voltage
Figure 6.21 Harmonic Transfer Function Phase Angle for 800 V Polarization Voltage

Nonlinear Transient Analysis

```plaintext
! *** Nonlinear transient analysis
/clear
/filnam,use5
rmresu,mirror,rom

/PREP7
ET,1,144
*do,i,1,20
  n,i
  *endo

rmuse,on
e,1,2,3,4,5,6,7,8
emore,9,10,11,12,13,14,15,16
emore,17,18,19,20
FINISH

/gst,off
/config,nres,5000

/solu
cycle_t=500e-6 ! Cycle time of one saw tooth
  ! about 20 times the cycle time of mode 1
rise_t=cycle_t/10 ! Rise time
num_cyc=3 ! Number of cycles
antype,transient
nropt,full
deltime,rise_t/10,rise_t/10,rise_t/10
auto,off
outres,all,all
```

Chapter 6: Reduced Order Modeling
This example demonstrates the response of a saw tooth like voltage function. The voltage displacement relationship is linearized since a high polarization voltage of 400 V is applied to both fixed electrodes. The amount of remaining oscillations depend strongly on the cycle time and the damping ratios. In practice, most mirror cells operate in a closed loop to a controller circuit to obtain better performance.
Figure 6.22 Modal Amplitudes vs. Time at Saw Tooth Like Voltage Function
Chapter 7: Direct Coupled-Field Analysis

The direct method for doing a coupled-field analysis involves a single analysis that uses a coupled-field element. Table 7.1: "Coupled-Field Elements" lists the elements that have coupled-field capability.

Table 7.1 Coupled-Field Elements

<table>
<thead>
<tr>
<th>Element Name</th>
<th>Description</th>
</tr>
</thead>
<tbody>
<tr>
<td>SOLID5</td>
<td>Coupled-field hexahedral</td>
</tr>
<tr>
<td>PLANE13</td>
<td>Coupled-field quadrilateral</td>
</tr>
<tr>
<td>FLUID29</td>
<td>Acoustic quadrilateral</td>
</tr>
<tr>
<td>FLUID30</td>
<td>Acoustic hexahedral</td>
</tr>
<tr>
<td>SOLID62</td>
<td>3-D magneto-structural hexahedral</td>
</tr>
<tr>
<td>PLANE67</td>
<td>Thermal-electric quadrilateral</td>
</tr>
<tr>
<td>LINK68</td>
<td>Thermal-electric line</td>
</tr>
<tr>
<td>SOLID69</td>
<td>Thermal-electric hexahedral</td>
</tr>
<tr>
<td>CIRCU94</td>
<td>Piezoelectric circuit</td>
</tr>
<tr>
<td>SOLID98</td>
<td>Coupled-field tetrahedral</td>
</tr>
<tr>
<td>TRANS109</td>
<td>2-D Electromechanical Transducer</td>
</tr>
<tr>
<td>FLUID116</td>
<td>Thermal-flow pipe</td>
</tr>
<tr>
<td>CIRCU124</td>
<td>General circuit</td>
</tr>
<tr>
<td>TRANS126</td>
<td>1-D Electromechanical Transducer</td>
</tr>
<tr>
<td>SHELL157</td>
<td>Thermal-electric shell</td>
</tr>
<tr>
<td>CONTA171</td>
<td>2-D surface to surface contact</td>
</tr>
<tr>
<td>CONTA172</td>
<td>2-D surface to surface contact</td>
</tr>
<tr>
<td>CONTA173</td>
<td>3-D surface to surface contact</td>
</tr>
<tr>
<td>CONTA174</td>
<td>3-D surface to surface contact</td>
</tr>
<tr>
<td>CONTA175</td>
<td>2-D/3-D node to surface contact</td>
</tr>
<tr>
<td>PLANE223</td>
<td>Coupled-field quadrilateral</td>
</tr>
<tr>
<td>SOLID226</td>
<td>Coupled-field hexahedral</td>
</tr>
<tr>
<td>SOLID227</td>
<td>Coupled-field tetrahedral</td>
</tr>
</tbody>
</table>

Note — Your finite element model may intermix certain coupled-field elements with the VOLT degree of freedom. To be compatible, the elements must have the same reaction force (see Element Compatibility in the ANSYS Low-Frequency Electromagnetic Analysis Guide).

The coupled-field element contains all the necessary degrees of freedom. It handles the field coupling by calculating the appropriate element matrices (matrix coupling) or element load vectors (load vector coupling). In linear problems with matrix coupling, coupled-field interaction is calculated in one iteration. Load vector coupling requires at least two iterations to achieve a coupled response. Nonlinear problems are iterative for both matrix and load vector coupling. Table 7.2: “Coupling Methods Used in Direct Coupled-Field Analyses” lists the different types of coupled-field analyses available in the ANSYS Multiphysics product using the direct method, and which type of coupling is present in each. See the ANSYS, Inc. Theory Reference for more details about matrix versus load vector coupling.
The ANSYS Professional program supports only thermal-electric direct coupling, and the ANSYS Emag program supports only electromagnetic and electromagnetic-circuit direct coupling.

### Table 7.2 Coupling Methods Used in Direct Coupled-Field Analyses

<table>
<thead>
<tr>
<th>Type of Analysis</th>
<th>Coupling Method</th>
</tr>
</thead>
<tbody>
<tr>
<td>Magneto-structural</td>
<td>Load vector</td>
</tr>
<tr>
<td>Electromagnetic</td>
<td>Matrix</td>
</tr>
<tr>
<td>Electromagnetic-thermal-structural</td>
<td>Load vector</td>
</tr>
<tr>
<td>Electromagnetic-thermal</td>
<td>Load vector</td>
</tr>
<tr>
<td>Piezoelectric</td>
<td>Matrix</td>
</tr>
<tr>
<td>Piezoresistive</td>
<td>Load vector</td>
</tr>
<tr>
<td>Thermal-pressure</td>
<td>Matrix and load vector</td>
</tr>
<tr>
<td>Velocity-thermal-pressure</td>
<td>Matrix</td>
</tr>
<tr>
<td>Pressure-structural (acoustic)</td>
<td>Matrix</td>
</tr>
<tr>
<td>Thermal-electric</td>
<td>Load vector (and matrix, if Seebeck coefficients are defined)</td>
</tr>
<tr>
<td>Magnetic-thermal</td>
<td>Load vector</td>
</tr>
<tr>
<td>Electrostatic-structural</td>
<td>Load vector</td>
</tr>
<tr>
<td>Electromagnetic-circuit</td>
<td>Matrix</td>
</tr>
<tr>
<td>Electro-structural-circuit</td>
<td>Matrix</td>
</tr>
<tr>
<td>Structural-thermal</td>
<td>Matrix or load vector (and matrix, if contact elements are used)</td>
</tr>
<tr>
<td>Structural-thermal-electric</td>
<td>Matrix and/or load vector</td>
</tr>
<tr>
<td>Thermal-piezoelectric</td>
<td>Matrix</td>
</tr>
</tbody>
</table>

*Note* — Coupled-field elements that use load vector coupling are not valid in a substructure analysis. Within the substructure generation pass, no iterative solution is available; therefore, the ANSYS program ignores all load vector and feedback coupling effects.

Because of the possible extreme nonlinear behavior of load vector coupled field elements, you may need to use the predictor and line search options to achieve convergence. Chapter 8, “Nonlinear Structural Analysis” in the *ANSYS Structural Analysis Guide* describes these options.

To speed up convergence in a coupled-field transient analysis, you may turn off the time integration effects for any DOFs that are not a concern. For example, if structural inertial and damping effects can be ignored in a thermal-structural transient analysis, you can issue `TIMINT,OFF,STRUC` to turn off the time integration effects for the structural DOFs.

Of the analysis types listed above, this chapter explains how to do thermal-electric, piezoelectric, piezoresistive, structural-thermal, structural-thermal-electric, magneto-structural, and electrostatic-structural analyses.

Electric contact is also available in ANSYS. See Modeling Electric Contact in the *ANSYS Contact Technology Guide* for details.

See Chapter 8, “Coupled Physics Circuit Simulation” for information on coupled physics circuit simulations.

The following direct coupled-field analysis topics are available:

7.1. Lumped Electric Elements

---

*ANSYS Coupled-Field Analysis Guide. ANSYS Release 10.0. 002184. © SAS IP, Inc.*
Section 7.1: Lumped Electric Elements

ANSYS provides several lumped elements that can be applied in pure electric circuit, circuit coupled magnetic, piezoelectric and coupled electromechanical analyses. This section provides a brief overview. For more details on DOF, through variables (force, reaction force), and element compatibility, refer to this guide, the ANSYS Elements Reference, and Element Compatibility in the ANSYS Low-Frequency Electromagnetic Analysis Guide.

CIRCU94 is a circuit element with electric potential (VOLT) DOF and negative electric charge (AMPS label) through variable (force, reaction force). Depending on KEYOPT selection it can act like a linear resistor, capacitor, inductor, or an independent voltage or current source. CIRCU94 can be applied in connection with other ANSYS elements having the same DOF and through variable (force, reaction force): SOLID5, PLANE13, SOLID98, PLANE230, SOLID231, and SOLID232 to simulate circuit coupled piezoelectric analysis.

CIRCU124 is a circuit element with electric potential (VOLT) DOF and electric current (AMPS label) through variable (force, reaction force). Depending on KEYOPT selection it can act like a linear resistor, capacitor, inductor, or a number of circuit source or coupled circuit source options. CIRCU124 can be applied in connection with other ANSYS elements having the same DOF and through variable (force, reaction force): SOLID5, PLANE67, SOLID69, SOLID98, CIRCU125, TRANS126, PLANE223, SOLID226, SOLID227, PLANE230, SOLID231, and SOLID232. CIRCU124 can also work together with magnetic elements PLANE13, PLANE53, and SOLID97 to simulate circuit fed magnetic analysis.

CIRCU125 is a circuit element with electric potential (VOLT) DOF and electric current (AMPS label) through variable (force, reaction force). Depending on KEYOPT selection it can act like a regular or Zener diode circuit. CIRCU125 can be applied in connection with other ANSYS elements having the same DOF and through variable (force, reaction force): CIRCU124, TRANS126, PLANE67, and SOLID69.

TRANS126 is an electromechanical transducer with electric potential (VOLT) as well as mechanical displacement (UX, UY, UZ) DOFs and electric current (AMPS label), as well as mechanical force (FX, FY, FZ) through variables (force, reaction force). TRANS126 can be applied in connection with other ANSYS elements having the same DOF and through variable (force, reaction force): TRANS126 can be applied in connection with all regular ANSYS mechanical elements to simulate strongly coupled electromechanical interactions, a characteristic of MEMS design.
7.2. Thermal-Electric Analysis

This analysis, available in the ANSYS Multiphysics product, can account for the following thermoelectric effects:

- **Joule heating** - Heating occurs in a conductor carrying an electric current. Joule heat is proportional to the square of the current, and is independent of the current direction.

- **Seebeck effect** - A voltage (Seebeck EMF) is produced in a thermoelectric material by a temperature difference. The induced voltage is proportional to the temperature difference. The proportionality coefficient is known as the Seebeck coefficient (\( \alpha \)).

- **Peltier effect** - Cooling or heating occurs at the junction of two dissimilar thermoelectric materials when an electric current flows through the junction. Peltier heat is proportional to the current, and changes sign if the current direction is reversed.

- **Thomson effect** - Heat is absorbed or released in a non-uniformly heated thermoelectric material when electric current flows through it. Thomson heat is proportional to the current, and changes sign if the current direction is reversed.

Typical applications include heating coils, fuses, thermocouples, and thermoelectric coolers and generators. For more information, refer to Thermoelectrics in the *ANSYS, Inc. Theory Reference*.

7.2.1. Elements Used in a Thermal-Electric Analysis

The ANSYS program includes a variety of elements you can use to model thermal-electric coupling. Table 7.3: “Elements Used in Thermal-Electric Analyses” summarizes them briefly. For detailed descriptions of the elements and their characteristics (DOFs, KEYOPT options, inputs and outputs, etc.), see the *ANSYS Elements Reference*.

LINK68, PLANE67, SOLID69, and SHELL157 are special purpose thermal-electric elements. The coupled-field elements (SOLID5, SOLID98, PLANE223, SOLID226, and SOLID227) require you to select the element DOFs for a thermal-electric analysis: TEMP and VOLT. For SOLID5 and SOLID98, set KEYOPT(1) to 0 or 1. For PLANE223, SOLID226, and SOLID227, set KEYOPT(1) to 110.

**Table 7.3 Elements Used in Thermal-Electric Analyses**

<table>
<thead>
<tr>
<th>Elements</th>
<th>Thermoelectric Effects</th>
<th>Material Properties</th>
<th>Analysis Types</th>
</tr>
</thead>
<tbody>
<tr>
<td>LINK68 - Thermal-Electric Line</td>
<td>Joule Heating</td>
<td>KXX, KYY, KZZ</td>
<td>Static</td>
</tr>
<tr>
<td>PLANE67 - Thermal-Electric Quadrilateral</td>
<td></td>
<td>RSVX, RSVY, RSVZ</td>
<td>Transient (transient thermal effects only)</td>
</tr>
<tr>
<td>SOLID69 - Thermal-Electric Hexahedral</td>
<td></td>
<td>DENS, C, ENTH</td>
<td></td>
</tr>
<tr>
<td>SOLID5 - Coupled-Field Hexahedral</td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>SOLID98 - Coupled-Field Tetrahedral</td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>SHELL157 - Thermal-Electric Shell</td>
<td></td>
<td></td>
<td></td>
</tr>
</tbody>
</table>
7.2.2. Performing a Thermal-Electric Analysis

The analysis can be either steady-state (ANTYPE,STATIC) or transient (ANTYPE,TRANS). It follows the same procedure as a steady-state or transient thermal analysis. (See Steady-State Thermal Analysis and Transient Thermal Analysis in the ANSYS Thermal Analysis Guide.)

To perform a thermal-electric analysis, you need to specify the element type and material properties. For Joule heating effects, you must define both electrical resistivity (RSVX, RSVY, RSVZ) and thermal conductivity (KXX, KYY, KZZ). Mass density (DENS), specific heat (C), and enthalpy (ENTH) may be defined to take into account thermal transient effects. These properties may be constant or temperature-dependent.

A transient analysis using PLANE223, SOLID226, or SOLID227 can account for both transient thermal and transient electrical effects. You must define electric permittivity (PERX, PERY, PERZ) to model the transient electrical effects. A transient analysis using LINK68, PLANE67, SOLID69, SOLID5, SOLID98, or SHELL157 can only account for transient thermal effects.

To include the Seebeck-Peltier thermoelectric effects, you need to specify a PLANE223, SOLID226, or SOLID227 element type and a Seebeck coefficient (SBKX, SBKY, SBKZ) (MP). You also need to specify the temperature offset from zero to absolute zero (TOFFST). To capture the Thomson effect, you need to specify the temperature dependence of the Seebeck coefficient (MPDATA).

PLANE67 and PLANE223 assume a unit thickness; they do not allow thickness input. If the actual thickness (t) is not uniform, you need to adjust the material properties as follows: multiply the thermal conductivity and density by t, and divide the electrical resistivity by t.

Be sure to define all data in consistent units. For example, if the current and voltage are specified in amperes and volts, you must use units of watts/length-degree for thermal conductivity. The output Joule heat will then be in watts.

For problems with convergence difficulties, activate the line search capability (LNSRCH).

See Section 7.9: Sample Thermoelectric Cooler Analysis (Batch or Command Method) and Section 7.10: Sample Thermoelectric Generator Analysis (Batch or Command Method) for example problems.

7.3. Piezoelectric Analysis

Piezoelectrics is the coupling of structural and electric fields, which is a natural property of materials such as quartz and ceramics. Applying a voltage to a piezoelectric material creates a displacement, and vibrating a piezoelectric material generates a voltage. A typical application of piezoelectric analysis is a pressure transducer. Possible piezoelectric analysis types (available in the ANSYS Multiphysics or ANSYS Mechanical products only) are static, modal, prestressed modal, harmonic, prestressed harmonic, and transient.
To do a piezoelectric analysis, you need to use one of these element types:

- PLANE13, KEYOPT(1) = 7 coupled-field quadrilateral solid
- SOLID5, KEYOPT(1) = 0 or 3 coupled-field brick
- SOLID98, KEYOPT(1) = 0 or 3 coupled-field tetrahedron
- PLANE223, KEYOPT(1) = 1001, coupled-field 8-node quadrilateral
- SOLID226, KEYOPT(1) = 1001, coupled-field 20-node brick
- SOLID227, KEYOPT(1) = 1001, coupled-field 10-node tetrahedron

PLANE13, SOLID5, and SOLID98 are available in ANSYS Multiphysics, ANSYS Mechanical, ANSYS PrepPost, and ANSYS ED. PLANE223, SOLID226, and SOLID227 are available in ANSYS Multiphysics, ANSYS PrepPost, and ANSYS ED.

The KEYOPT settings activate the piezoelectric degrees of freedom, displacements and VOLT. For SOLID5 and SOLID98, setting KEYOPT(1) = 3 activates the piezoelectric only option.

The piezoelectric KEYOPT settings also make large deflection and stress stiffening effects available using the NLGEOM, SSTIF, and PSTRES commands. (See the ANSYS Commands Reference for more information on these commands. See the ANSYS Structural Analysis Guide and Chapter 3 of the ANSYS, Inc. Theory Reference for more information on large deflection and stress stiffening capabilities.) For PLANE13, large deflection and stress stiffening capabilities are available for KEYOPT(1) = 7. For SOLID5 and SOLID98, large deflection and stress stiffening capabilities are available for KEYOPT(1) = 3. In addition, small deflection stress stiffening capabilities are available for KEYOPT(1) = 0.

Nota — Automatic solution control is not available for a piezoelectric analysis. The SOLCONTROL default settings are only available for a pure structural or pure thermal analysis. For a large deflection piezoelectric analysis, you must use nonlinear solution commands to specify your settings. For general information on these commands, refer to Section 8.5: Running a Nonlinear Analysis in ANSYS in the ANSYS Structural Analysis Guide.

### 7.3.1. Points to Remember

The analysis may be static, modal, prestressed modal, harmonic, prestressed harmonic, or transient. Some important points to remember are:

- For modal analysis, Block Lanczos is the recommended (and default) solver.
- For static, full harmonic, or full transient analysis, choose the sparse matrix (SPARSE) solver or the Jacobi Conjugate Gradient (JCG) solver. The sparse solver is the default for static and full transient analyses. Depending on the chosen system of units or material property values, the assembled matrix may become ill-conditioned. When solving ill-conditioned matrices, the JCG iterative solver may converge to the wrong solution. The assembled matrix typically becomes ill-conditioned when the magnitudes of the structural DOF and electrical DOF start to vary significantly (more than 1e15).
- For transient analyses, specify \texttt{ALPHA = 0.25, DELTA = 0.5, and THETA = 0.5} on the \texttt{TINTP} command (Main Menu> Preprocessor> Loads> Time/Frequency>Time Integration).
- A prestressed harmonic analysis can only follow a small deflection analysis.
- For PLANE13, SOLID5, and SOLID98, the force label for the VOLT DOF is AMPS. For PLANE223, SOLID226, and SOLID227, the force label for the VOLT degree of freedom is CHRG. Use these labels in \texttt{F, CNVTOL, RFORCE, etc.}
- To do a piezoelectric-circuit analysis, use CIRCU94.
- The capability to model dielectric losses using the dielectric loss tangent property (input on \texttt{MP,LSST}) is available only for PLANE223, SOLID226, and SOLID227.
7.3.2. Material Properties

A piezoelectric model requires permittivity (or dielectric constants), the piezoelectric matrix, and the elastic coefficient matrix to be specified as material properties. These are explained next.

### 7.3.2.1. Permittivity Matrix (Dielectric Constants)

For SOLID5, PLANE13, or SOLID98 you specify relative permittivity values as PERX, PERY, and PERZ on the MP command (Main Menu> Preprocessor> Material Props> Material Models> Electromagnetics> Relative Permittivity> Orthotropic). (Refer to the EMUNIT command for information on free-space permittivity.) The permittivity values represent the diagonal components $\varepsilon_{11}$, $\varepsilon_{22}$, and $\varepsilon_{33}$ respectively of the permittivity matrix $\varepsilon^S$. (The superscript "S" indicates that the constants are evaluated at constant strain.) That is, the permittivity input on the MP command will always be interpreted as permittivity at constant strain $\varepsilon^S$.

**Note** — If you enter permittivity values less than 1 for SOLID5, PLANE13, or SOLID98, the program interprets the values as absolute permittivity.

For PLANE223, SOLID226, and SOLID227, you can specify permittivity either as PERX, PERY, PERZ on the MP command or by specifying the terms of the anisotropic permittivity matrix using the TB,DPER and TBDATA commands. If you choose to use the MP command to specify permittivity, the permittivity input will be interpreted as permittivity at constant strain. If you choose to use the TB,DPER command (Main Menu> Preprocessor> Material Props> Material Models> Electromagnetics> Relative Permittivity> Anisotropic), you can specify the permittivity matrix at constant strain $\varepsilon^S$ ($TBOPT = 0$) or at constant stress $\varepsilon^T$ ($TBOPT = 1$). The latter input will be internally converted to permittivity at constant strain $\varepsilon^S$ using the piezoelectric strain and stress matrices. The values input on either MP,PERX or TB,DPER will always be interpreted as relative permittivity.

### 7.3.2.2. Piezoelectric Matrix

You can define the piezoelectric matrix in $[e]$ form (piezoelectric stress matrix) or in $[d]$ form (piezoelectric strain matrix). The $[e]$ matrix is typically associated with the input of the anisotropic elasticity in the form of the stiffness matrix $[c]$, while the $[d]$ matrix is associated with the compliance matrix $[s]$.

**Note** — ANSYS will convert a piezoelectric strain matrix $[d]$ matrix to a piezoelectric stress matrix $[e]$ using the elastic matrix at the first defined temperature. To specify the elastic matrix required for this conversion, use the TB,ANEL command (not the MP command).

This 6 x 3 matrix (4 x 2 for 2-D models) relates the electric field to stress ([e] matrix) or to strain ([d] matrix). Both the [e] and the [d] matrices use the data table input described below:

\[
[e] = \begin{bmatrix}
x & y & z \\
x & e_{11} & e_{12} & e_{13} \\
y & e_{21} & e_{22} & e_{23} \\
z & e_{31} & e_{32} & e_{33} \\
xy & e_{41} & e_{42} & e_{43} \\
yz & e_{51} & e_{52} & e_{53} \\
xyz & e_{61} & e_{62} & e_{63} \\
\end{bmatrix} \\
\begin{bmatrix}
x & y \\
e_{11} & e_{12} \\
e_{21} & e_{22} \\
e_{31} & e_{32} \\
e_{41} & e_{42} \\
\end{bmatrix} \quad \begin{bmatrix}
3 - D \\
2 - D \\
\end{bmatrix}
\]

The TB,PIEZ and TBDATA commands are used to define the piezoelectric matrix; see your ANSYS Commands Reference for the order of input of these constants.
To define the piezoelectric matrix via the GUI, use the following:

Main Menu> Preprocessor> Material Props> Material Models> Piezoelectrics> Piezoelectric matrix

For most published piezoelectric materials, the order used for the piezoelectric matrix is x, y, z, yz, xz, xy, based on IEEE standards (see ANSI/IEEE Standard 176–1987), while the ANSYS input order is x, y, z, xy, yz, xz as shown above. This means that you need to transform the matrix to the ANSYS input order by switching row data for the shear terms as shown below:

- IEEE constants \([e_{61}, e_{62}, e_{63}]\) would be input as the ANSYS xy row
- IEEE constants \([e_{41}, e_{42}, e_{43}]\) would be input as the ANSYS yz row
- IEEE constants \([e_{51}, e_{52}, e_{53}]\) would be input as the ANSYS xz row

\[
\text{ANSYS } [e] = \begin{bmatrix}
    \varepsilon_{11} & \varepsilon_{12} & \varepsilon_{13} \\
    \varepsilon_{21} & \varepsilon_{22} & \varepsilon_{23} \\
    \varepsilon_{31} & \varepsilon_{32} & \varepsilon_{33} \\
    \varepsilon_{16} & \varepsilon_{26} & \varepsilon_{36} \\
    \varepsilon_{41} & \varepsilon_{42} & \varepsilon_{43} \\
    \varepsilon_{51} & \varepsilon_{52} & \varepsilon_{53} \\
\end{bmatrix}
\]

7.3.2.3. Elastic Coefficient Matrix

This 6 x 6 symmetric matrix (4 x 4 for 2-D models) specifies the stiffness ([c] matrix) or compliance ([s] matrix) coefficients.

Note — This section follows the IEEE standard notation for the elastic coefficient matrix [c]. This matrix is also referred to as [D] in other areas of ANSYS Help.

The elastic coefficient matrix uses the following data table input:

\[
[c] = \begin{bmatrix}
    c_{11} & c_{12} & c_{13} & c_{16} & c_{14} & c_{15} \\
    c_{21} & c_{22} & c_{23} & c_{26} & c_{24} & c_{25} \\
    c_{31} & c_{32} & c_{33} & c_{36} & c_{34} & c_{35} \\
    c_{41} & c_{42} & c_{43} & c_{44} & c_{46} & c_{45} \\
    c_{51} & c_{52} & c_{53} & c_{54} & c_{55} & c_{56} \\
    c_{61} & c_{62} & c_{63} & c_{64} & c_{65} & c_{66} \\
\end{bmatrix}
\]

Use the TB, ANEL (Main Menu> Preprocessor> Material Props> Material Models> Structural> Linear> Elastic> Anisotropic) and TBDATA commands to define the coefficient matrix [c] (or [s], depending on the TBOPT settings); see the ANSYS Commands Reference for the order of input of these constants. As explained for the piezoelectric matrix, most published piezoelectric materials use a different order for the [c] matrix. You need to transform the IEEE matrix to the ANSYS input order by switching row and column data for the shear terms as shown below:

- IEEE terms \([c_{61}, c_{62}, c_{63}, c_{66}]\) would be input as the ANSYS xy row
7.4. Piezoresistive Analysis

The piezoresistive effect is the change of electric resistivity of the material caused by an applied mechanical strain or stress. Many materials change their resistance when strained, but the piezoresistive effect is most pronounced in semiconductors. Semiconductor piezoresistive sensing elements, or piezoresistors, are typically used as pressure and force sensors, where the applied mechanical load is converted into a proportional electric signal. Typical applications of piezoresistors are pressure transducers and accelerometers.

You use piezoresistive analysis to determine the change in electric field or current distributions due to applied forces or pressure. The elements that allow you to do a piezoresistive analysis are:

- **PLANE223, KEYOPT(1) = 101** - coupled-field 8-node quadrilateral
- **SOLID226, KEYOPT(1) = 101** - coupled-field 20-node brick
- **SOLID227, KEYOPT(1) = 101** - coupled-field 10-node tetrahedron

The analysis type can be either steady-state (**ANTYPE,0**) or transient (**ANTYPE,4**).

7.4.1. Points to Remember

- At least two iterations are required to calculate the piezoresistive effect.
- The force label for the **VOLT** degree of freedom is **AMPS**. Use this label in **F, CNVTOL, RFORCE**, etc.
- To do a piezoresistive-circuit analysis, use **CIRCU124**.
- Use the **JC** label on **PRNSOL/PLNSOL, PRESOL/PLESOL, PRVECT/PLVECT** commands to print or plot conduction current density results.
- Automatic solution control (**SOLCONTROL**) is not available for a piezoresistive analysis.
7.4.2. Material Properties

A piezoresistive analysis requires the specification of electrical resistivity, the elastic coefficients, and the piezoresistive matrix. These are explained next.

7.4.2.1. Electrical Resistivity

You specify electrical resistivity values as RSVX, RSVY, RSVZ on the MP command (Main Menu> Preprocessor> Material Props> Material Models> Electromagnetics> Resistivity> Orthotropic).

Note — To take into account capacitive effects in a transient piezoresitive analysis, you can specify electrical permittivities as PERX, PERY, and PERZ on the MP command.

7.4.2.2. Elastic Coefficient Matrix

Input the elastic coefficient matrix using the data table input (TB,ANEL and TBDATA commands). See Section 7.3.2.3: Elastic Coefficient Matrix for a discussion on the elastic coefficient matrix. As an alternative, you can specify Young's modulus (MP,EX command) and Poisson's ratio (MP,NUXY command). To specify these values via the GUI:

Main Menu> Preprocessor> Material Props> Material Models> Structural> Linear> Elastic> Orthotropic

7.4.2.3. Piezoresistive Matrix

You can specify piezoresistive matrix either in the form of piezoresistive stress matrix \([\pi]\) or piezoresistive strain matrix \([m]\) via the TB,PZRS and TBDATA commands.

The piezoresistive stress matrix \([\pi]\) \((TBOPT=0)\) uses stress to calculate the change in electric resistivity due to the piezoresistive effect. The piezoresistive strain matrix \([m]\) \((TBOPT=1)\) uses elastic strain to calculate the change in electric resistivity due to the piezoresistive effect. See Section 11.4: Piezoresistivity in the ANSYS, Inc. Theory Reference for more information.

In a general case, the piezoresistive matrix is a non-symmetric 6x6 matrix that relates the x, y, z, xy, yz, xz terms of stress or strain to the x, y, z, xy, yz, xz terms of electric resistivity via 36 constants. See Section 2.5.8: Piezoresistive Materials in the ANSYS Elements Reference for a description of the matrix used. For the semiconductor materials (e.g., silicon) that belong to the cubic group of symmetry, the piezoresistive matrix has only three independent coefficients, \(\pi_{11}, \pi_{12}, \pi_{44}\):

\[
\begin{bmatrix}
\pi_{11} & \pi_{12} & \pi_{12} & 0 & 0 & 0 \\
\pi_{12} & \pi_{11} & \pi_{12} & 0 & 0 & 0 \\
\pi_{12} & \pi_{12} & \pi_{11} & 0 & 0 & 0 \\
0 & 0 & 0 & \pi_{44} & 0 & 0 \\
0 & 0 & 0 & 0 & \pi_{44} & 0 \\
0 & 0 & 0 & 0 & 0 & \pi_{44}
\end{bmatrix}
\]

and \([\pi]\) can be input as follows:

TB,PZRS
TBDATA,1,\pi_{11}, \pi_{12}, \pi_{12}
TBDATA,7,\pi_{12}, \pi_{11}, \pi_{12}
TBDATA,13,\pi_{12}, \pi_{12}, \pi_{11}
To define the piezoresistive matrix via the GUI, use the following:

**Main Menu > Preprocessor > Material Props > Material Models > Piezoresistivity > Piezoresistive matrix**

Be sure to define data in consistent units. When modeling micro-electromechanical systems (MEMS), it is best to use µMKS or µMSVfA units (see Table 1.6: “Piezoresistive Conversion Factors for MKS to µMKS” and Table 1.13: “Piezoresistive Conversion Factors for MKS to µMKSfA”).

See Section 7.14: Sample Piezoresistive Analysis (Batch or Command Method) for an example of a piezoresistive analysis.

### 7.5. Structural-Thermal Analysis

This capability, available in the ANSYS Multiphysics product, provides you with the ability to perform thermal-stress analyses. In dynamic analyses, you can also include the piezocaloric effect. Applications of the latter include thermoelastic damping in metals and MEMS devices such as resonator beams.

#### 7.5.1. Elements Used in a Structural-Thermal Analysis

The ANSYS program includes a variety of elements that you can use to perform a coupled structural-thermal analysis. Table 7.4: “Elements Used in Structural-Thermal Analyses” summarizes them. For detailed descriptions of the elements and their characteristics (DOFs, KEYOPT options, inputs and outputs, etc.), see the ANSYS Elements Reference.

For a coupled structural-thermal analysis, you need to select the UX, UY, UZ, and TEMP element DOFs. For SOLID5 or SOLID98, set KEYOPT(1) to 0. For PLANE13 set KEYOPT(1) to 4. For PLANE223, SOLID226, or SOLID227, set KEYOPT(1) to 11.

To include piezocaloric effects in dynamic analyses (transient and harmonic), you need to use PLANE223, SOLID226, or SOLID227.

#### Table 7.4 Elements Used in Structural-Thermal Analyses

<table>
<thead>
<tr>
<th>Elements</th>
<th>Effects</th>
<th>Analysis Types</th>
</tr>
</thead>
<tbody>
<tr>
<td>SOLID5 - Coupled-Field Hexahedral</td>
<td>Thermoelastic (Thermal Stress)</td>
<td>Static</td>
</tr>
<tr>
<td></td>
<td></td>
<td>Full Transient</td>
</tr>
<tr>
<td>PLANE13 - Coupled-Field Quadrilateral</td>
<td></td>
<td></td>
</tr>
<tr>
<td>SOLID98 - Coupled-Field Tetrahedral</td>
<td></td>
<td></td>
</tr>
<tr>
<td>PLANE223 - Coupled-Field Quadrilateral</td>
<td>Thermoelastic (Thermal Stress and Piezocaloric)</td>
<td>Static</td>
</tr>
<tr>
<td>SOLID226 - Coupled-Field Hexahedral</td>
<td></td>
<td>Full Harmonic</td>
</tr>
<tr>
<td>SOLID227 - Coupled-Field Tetrahedral</td>
<td></td>
<td>Full Transient</td>
</tr>
</tbody>
</table>
7.5.2. Performing a Structural-Thermal Analysis

To perform a structural-thermal analysis you need to do the following:

1. Select a coupled-field element that is appropriate for the analysis (Table 7.4: “Elements Used in Structural-Thermal Analyses”). Use KEYOPT (1) to select the UX, UY, UZ, and TEMP element DOFs.

2. Specify structural material properties:
   - If the material is isotropic or orthotropic, Young’s moduli (EX, EY, EZ), Poisson’s ratios (PRXY, PRYZ, PRXZ, or NUXY, NUYZ, NUXZ), and shear moduli (GXY, GYZ, and GXZ) are input using the MP command.
   - If the material is anisotropic, the elastic stiffness matrix is input using TB,ANEL.

3. Specify thermal material properties:
   - Specify thermal conductivities (KXX, KYY, KZZ) using the MP command.
   - To take into account thermal transient effects, specify mass density (DENS) and specific heat (C) or enthalpy (ENTH) using the MP command.

4. Specify coefficients of thermal expansion (ALPX, ALPY, ALPZ), thermal strains (THSX, THSY, THSZ), or the instantaneous coefficients of thermal expansion (CTEX, CTEY, CTEZ) using the MP command.

5. Specify the reference temperature for the thermal strain calculations using the TREF command.

6. Apply structural and thermal loads.

7. The following only apply to the PLANE223, SOLID226, or SOLID227 elements:
   - If you perform a static or full transient analysis, you can use KEYOPT(2) to select a strong (matrix) or weak (load vector) structural-thermal coupling. Strong coupling produces an unsymmetric matrix. In a linear analysis, a strong coupled response is achieved after one iteration. Weak coupling produces a symmetric matrix and requires at least two iterations to achieve a coupled response.
     
     *Note* — For full harmonic analysis with these elements, strong structural-thermal coupling only applies.

   - These elements support a piezocaloric effects calculation in dynamic analyses. For more information, see Thermoelasticity in the *ANSYS, Inc. Theory Reference*.

Note the following about the inputs for a piezocaloric effects calculation:

- Elastic coefficients are interpreted as isothermal coefficients, not adiabatic coefficients.
- Specific heat is assumed to be at constant pressure (or constant stress), and it is automatically converted to specific heat at constant volume (or constant strain).
- You need to specify the temperature offset from absolute zero to zero using the TOFFST command. This temperature offset is added to the temperature input on the TREF command to obtain the absolute reference temperature.
- All thermal material properties and loads must have the same energy units as shown in the following table. For the SI system, both energy and heat units are in Joules. For the British system, energy units are in-lbf or ft-lbf and heat units are in BTUs. British heat units (BTUs) must be converted to energy units of in-lbf or ft-lbf (1BTU = 9.34e3 in-lbf = 778.26 ft-lbf).
### Table 7.5 Units for Thermal Quantities

<table>
<thead>
<tr>
<th>Thermal Quantity</th>
<th>Units</th>
</tr>
</thead>
<tbody>
<tr>
<td>Thermal Conductivity</td>
<td>energy/length-temperature-time</td>
</tr>
<tr>
<td>Specific Heat</td>
<td>energy/mass-temperature</td>
</tr>
<tr>
<td>Heat Flux</td>
<td>energy/length²-time</td>
</tr>
<tr>
<td>Volumetric Heat Source</td>
<td>energy/length³-time</td>
</tr>
<tr>
<td>Heat Transfer Coefficient</td>
<td>energy/length²-temperature-time</td>
</tr>
</tbody>
</table>

See Section 7.11: Sample Structural-Thermal Harmonic Analysis (Batch or Command Method) for an example problem.

### 7.6. Structural-Thermal-Electric Analyses

You can perform structural-thermoelectric or thermal-piezoelectric analyses using SOLID5, PLAN13, SOLID98, PLAN123, SOLID226, or SOLID227. For detailed descriptions of the elements and their characteristics (DOFs, KEYOPT options, inputs and outputs, etc.), see the ANSYS Elements Reference.

For coupled structural-thermal-electric analyses, you need to select the UX, UY, UZ, TEMP, and VOLT element DOFs. For SOLID5 or SOLID98, set KEYOPT(1) to 0. The analysis type (structural-thermoelectric or thermo-piezoelectric) for those elements is determined by the electrical material property input (resistivity or permittivity). For PLAN123, SOLID226, and SOLID227, the analysis type is determined by KEYOPT(1). For those elements, set KEYOPT(1) to 111 for a structural-thermoelectric analysis or 1011 for a thermal-piezoelectric analysis.

### Table 7.6 Elements Used in a Structural-Thermal-Electric Analyses

<table>
<thead>
<tr>
<th>Elements</th>
<th>Effects</th>
<th>Analysis Types</th>
</tr>
</thead>
<tbody>
<tr>
<td>SOLID5 - Coupled-Field Hexahedral</td>
<td>Thermoelectric (Thermal Stress)</td>
<td>Static</td>
</tr>
<tr>
<td></td>
<td>Thermoelectric (Joule Heating)</td>
<td>Full Transient</td>
</tr>
<tr>
<td></td>
<td>Piezoelectric</td>
<td></td>
</tr>
<tr>
<td>SOLID98 - Coupled-Field Tetrahedral</td>
<td>Thermoelectric (Thermal Stress and Piezocaloric)</td>
<td>Structural-Thermoelectric</td>
</tr>
<tr>
<td></td>
<td>Thermoelectric (Joule Heating, Seebeck, Peltier, Thomson)</td>
<td>Static</td>
</tr>
<tr>
<td></td>
<td>Piezoresistive</td>
<td>Full Transient</td>
</tr>
<tr>
<td>PLANE223 - Coupled-Field Quadrilateral</td>
<td>Thermoelectric (Thermal Stress and Piezocaloric)</td>
<td>Thermal-Piezoelectric:</td>
</tr>
<tr>
<td>SOLID226 - Coupled-Field Hexahedral</td>
<td>Thermoelectric (Joule Heating, Seebeck, Peltier, Thomson)</td>
<td>Static</td>
</tr>
<tr>
<td></td>
<td>Piezoresistive</td>
<td>Full Harmonic</td>
</tr>
<tr>
<td>SOLID227 - Coupled-Field Tetrahedral</td>
<td>Thermoelectric (Thermal Stress and Piezocaloric)</td>
<td>Full Transient</td>
</tr>
<tr>
<td></td>
<td>Piezoelectric</td>
<td></td>
</tr>
</tbody>
</table>
7.6.1. Structural-Thermoelectric Analysis

In addition to the steps outlined in Section 7.5.2: Performing a Structural-Thermal Analysis, you need to specify electrical material properties and material properties for coupled-field effects.

1. Specify electrical resistivities (RSVX, RSVY, RSVZ) on the MP command.

2. The following only apply to the PLANE223, SOLID226, or SOLID227 elements:
   - You can also specify electric permittivity (PERX, PERY, PERZ) on the MP command to model transient electrical effects (capacitive effects). For more information, see Section 7.2: Thermal-Electric Analysis.
   - You can also specify Seebeck coefficients (SBKX, SBKY, SBKZ) on the MP command to include the Seebeck-Peltier themoelectric effects. For more information, see Section 7.2: Thermal-Electric Analysis.
   - You can also specify a piezoresistive matrix on the TB,PZRS command to include the piezoresistive effect. For more information, see Section 7.4: Piezoresistive Analysis.
   - To perform a circuit analysis, use the CIRCU124 element. For more information, see Using the CIRCU124 Element in the ANSYS Low-Frequency Electromagnetic Analysis Guide.

See Section 7.12: Sample Electro-Thermal Microactuator Analysis (Batch or Command Method) for an example problem.

7.6.2. Thermal-Piezoelectric Analysis

In addition to the steps outlined in Section 7.5.2: Performing a Structural-Thermal Analysis, you need to specify electrical material properties and material properties for coupled-field effects.

1. For SOLID5 or SOLID98, specify electric permittivity (PERX, PERY, PERZ) on the MP command. For PLANE223, SOLID226, and SOLID227, specify permittivity either as PERX, PERY, PERZ on the MP command or by specifying the terms of the anisotropic permittivity matrix using the TB,DPER and TBDATA commands. To model dielectric losses, use PLANE223, SOLID226, or SOLID227 and specify a loss tangent (MP,LSST). For more information, see Section 7.3: Piezoelectric Analysis.

2. Specify the piezoelectric matrix on the TB,PIEZ command. For more information, see Section 7.3.2.2: Piezoelectric Matrix.

3. To perform a circuit analysis, use the CIRCU94 element. For more information, see Piezoelectric-Circuit Simulation.

7.7. Magneto-Structural Analysis

You use this analysis, available in the ANSYS Multiphysics product, to determine the magnetic forces acting on a current-carrying conductor or magnetic material and the subsequent structural deformation expected from the action of these magnetic forces. Applications involve determining forces, deformations and stresses on structures subjected to steady-state or transient magnetic fields where you want to determine the impacts on structural design. Typical applications include pulsed excitation of conductors, structural vibration resulting from transient magnetic fields, armature motion in solenoid actuators, and magneto-forming of metals.

To do direct magneto-structural analysis, you must use one of the following element types:

- PLANE13 - coupled-field quadrilateral solid
- SOLID5 - coupled-field brick
- SOLID62 - magneto-structural brick
- SOLID98 - coupled-field tetrahedron
7.7.1. Points to Remember

The analysis may be either static or transient. It follows the same procedure as a static or transient magnetic analysis. (See the ANSYS Low-Frequency Electromagnetic Analysis Guide.) Some important points to remember are:

- PLANE13 and SOLID62 use the vector potential formulation and can be used for static and transient analyses. SOLID5 and SOLID98 use the scalar potential formulation and can be used only in a static analysis.

  Note — Do not use the PCG solver if your model contains SOLID62 elements.

- You should activate the large deflection feature, available in PLANE13 and SOLID62, whenever structural deformation affects the magnetic field. This is a highly nonlinear analysis, so you should ramp the load slowly using many intermediate substeps. Also, surrounding the deflecting body with air elements that have nominal structural properties is required, because the surrounding air elements must "absorb" the deflection of the body. You can then rigidly fix the exterior of the air region by constraining the degrees of freedom.

- You can solve a dynamic analysis involving small movement of a body (that is, an armature of a solenoid). Small movement is characterized as movement of the armature and surrounding air elements up to a point where mesh distortion remains acceptable. You should assign the surrounding air elements extremely flexible structural properties. Also, be sure to turn off extra shape functions in the air elements. Auto time-stepping is sensitive to the mass and stiffness of the system. To dampen numerical noise, adjust the GAMMA parameter on the TINTP command (using a value as high as 1.0). To aid convergence, turn adaptive descent off and use convergence criteria based on force (F) and vector potential (A).

7.8. Electromechanical Analysis

Electrostatic-mechanical coupling involves coupling of forces produced by an electrostatic field with a mechanical device. Typically, this type of simulation is done on micro-electromechanical (MEMS) devices such as comb drives, switches, filters, accelerometers, and torsional mirrors. This section describes the direct-coupled electrostatic-structural coupling available in the TRANS126 and TRANS109 transducer elements. For sequential coupling, use the ANSYS Multi-field solver, described in Chapter 3, “The ANSYS Multi-field (TM) Solver - MFS Single-Code Coupling”.

7.8.1. The 1-D Transducer Element

TRANS126 is a "reduced-order" element which is intended for use as a transducer in structural finite element simulations or as a transducer in "lumped" electromechanical circuit simulation. "Reduced-order" means that the electrostatic characteristics of an electromechanical device are captured in terms of the device’s capacitance over a range of displacements (or stroke of the device) and formulated in a simple coupled beam-like element. Refer to the ANSYS Elements Reference and the ANSYS, Inc. Theory Reference for a full description of the TRANS126 element. Figure 7.1: “Procedure for Extracting Capacitance” shows a typical progression of computing the devices capacitance in an electrostatic simulation, computing the capacitance of the device over a range of motion (parameter “d” in Figure 7.1: “Procedure for Extracting Capacitance”), and incorporating these results as the input characteristics for the transducer element.
7.8.1.1. **Element Physics**

TRANS126 is a fully coupled element which relates the electrostatic response and the structural response of an electromechanical device. Because the element is fully coupled, you can use it effectively in static, harmonic, transient, and modal analyses. Nonlinear analysis can exploit the full system tangent stiffness matrix. Small signal harmonic sweep and natural frequencies reflect coupled full system behavior. For the case with motion in the x-direction, the charge on the device is related to the voltage applied to the device as:

\[ Q = C(x) \cdot V \]

where \( V \) is the voltage across the device electrodes, \( C(x) \) is the capacitance between electrodes (as a function of \( x \)), and \( Q \) is the charge on the electrode.

The current is related to the charge as:

\[ I = \frac{dQ}{dt} = \left( \frac{dC(x)}{dx} \cdot \frac{dx}{dt} \right) \cdot (V) + C(x) \cdot \frac{dV}{dt} \]

where the term \( \left( \frac{dC(x)}{dx} \cdot \frac{dx}{dt} \right) \cdot (V) \) is the motion induced current and the term \( C(x) \cdot \frac{dV}{dt} \) is the voltage rate current.

The electrostatic force between the electrodes is given by:

\[ F = \left( \frac{1}{2} \right) \left( \frac{dC(x)}{dx} \right) \cdot (V)^2 \]

As can be seen from the above equations, the capacitance of the device over a range of motion characterizes the electromechanical response of the device.

7.8.1.2. **A Reduced Order Model**

As shown in Figure 7.2: "Reduced Order Model", you can analyze MEMS devices using "reduced order" models consisting of mechanical spring, damper, and mass elements (COMBIN14, COMBIN39, and MASS21), and the electromechanical transducer element (TRANS126). The transducer element converts energy from an electrostatic domain into a mechanical domain. It represents the capacitive response of a device to motion in one direction.
You can use the **EMTGEN** command to generate a distributed set of TRANS126 elements between the surface of a moving structure and a plane (i.e. ground plane). This arrangement allows for fully coupled electrostatic-structural simulations for cases where the gap is small compared to the overall area of the structure. Typical applications include accelerometers, switches, and micromirror devices. See the *ANSYS Commands Reference* for more information on the **EMTGEN** command.

The TRANS126 element supports motion in the nodal X, Y, and Z directions. You can combine multiple elements to represent a full 3-D translational response of a device. Accordingly, you can model an electrostatic-driven structure by a reduced order element that fully characterizes the coupled electromechanical response.

You can link the transducer element into 2-D or 3-D finite element structural models to perform complex simulations for large signal static and transient analysis as well as small signal harmonic and modal analysis. See Section 7.15: Sample Electromechanical Analysis (Batch or Command Method) for a sample electromechanical analysis using the TRANS126 transducer element.

### 7.8.1.3. Static Analysis

For a static analysis, an applied voltage to a transducer will produce a force which acts on the structure. For example, voltages applied \( V_1 > V_2 \) to the electromechanical transducer elements (TRANS126) will produce an electrostatic force to rotate the torsional beam shown in Figure 7.3: “Micromirror Model”.

The static equilibrium of an electrostatic transducer may be unstable. With increasing voltage, the attraction force between the capacitor plates increases and the gap decreases. For a gap distance \( d \), the spring restoring
force is proportional to $1/d$ and the electrostatic force is proportional to $1/d^2$. When the capacitor gap decreases to a certain point, the electrostatic attraction force becomes larger than the spring restoring force and the capacitor plates snap together. Conversely, when the capacitor voltage decreases to a certain value, the electrostatic attraction force becomes smaller than the spring restoring force and the capacitor plates snap apart.

The transducer element can exhibit hysteresis as shown in Figure 7.4: “Electromechanical Hysteresis”. The voltage ramps up to the pull-in value and then back down to the release value.

**Figure 7.4 Electromechanical Hysteresis**

The transducer element by nature has both stable and unstable solutions as shown in Figure 7.5: “Static Stability Characteristics”. The element will converge to either solution depending on the starting location (initial gap size).
System stiffness consists of structural stiffness and electrostatic stiffness and it can be negative. Structural stiffness is positive because the force increases when a spring is stretched. However, electrostatic stiffness of a parallel plate capacitor is negative. The attraction force between the plates decreases with an increasing gap.

If the system stiffness is negative, convergence problems can occur near unstable solutions. If you encounter convergence problems while using TRANS126, use its built-in augmented stiffness method (KEYOPT(6) = 1). In this method, the electrostatic stiffness is set to zero to guarantee a positive system stiffness. After convergence is reached, the electrostatic stiffness is automatically reestablished for postprocessing and subsequent analyses.

You must completely specify the voltage across the transducer in a static analysis. You may also apply nodal displacements and forces. Using the IC command for initial displacements may help to converge the problem. See Chapter 2, “Structural Static Analysis” in the ANSYS Structural Analysis Guide for general information on performing a static analysis.

7.8.1.4. Modal Analysis

You may use TRANS126 to perform a prestressed modal analysis to determine the system eigenfrequencies. Of interest in many devices is the frequency shift when an applied DC voltage is placed on the electrodes of the transducer. You can simulate this effect by performing a static analysis of the device first with the applied DC voltage to the transducer, and then performing a "prestress" modal analysis on the structure. The TRANS126 element requires the unsymmetric eigenvalue solver (MODOPT, UNSYM) for modal analysis if a voltage is left unspecified at a transducer node. If the transducer element has a fully prescribed voltage (at both nodes), the problem becomes symmetric. In this case, set KEYOPT(3) = 1 for the transducer element and select a symmetric eigensolver (MODOPT, LANB). (MODOPT, LANB is the default.) See Chapter 3, “Modal Analysis” in the ANSYS Structural Analysis Guide for general information on performing a modal analysis as well as the steps necessary to perform a prestressed modal analysis.
7.8.1.5. Harmonic Analysis

You can simulate a prestressed full harmonic analysis on a structure, incorporating a transducer element TRANS126 to provide a small-signal AC voltage signal. Similarly, a mechanically excited structure will produce a voltage and current in the transducer. A static analysis must be performed prior to a small-signal harmonic analysis. Typically a device operates with a DC bias voltage and a small-signal AC voltage. The small-signal excitation simulation about a DC bias voltage is in essence a static analysis (with the applied DC voltage) followed by a full harmonic analysis (with the applied AC excitation). This capability is often required to tune a system’s resonance frequency for such devices as filters, resonators, and accelerometers. See Chapter 4, “Harmonic Response Analysis” in the ANSYS Structural Analysis Guide for general information on performing a modal analysis as well as the steps necessary to perform a prestressed harmonic analysis.

7.8.1.6. Transient Analysis

A full transient analysis may be run incorporating TRANS126 attached to a complex finite element structure. You can apply any arbitrary large-signal time-varying excitation to the transducer or structure to produce a fully-coupled transient electromechanical response. You can apply both voltage and current as electrical loads, and displacement or force as mechanical loads. However, you must exercise care when specifying initial conditions for voltage and displacement because you can use the IC command to specify both voltage and voltage rate (using VALUE1 and VALUE2 of the IC command), as well as displacement and velocity. In addition, you can use the CNVTOL command to specify convergence criteria for the voltage (VOLT label) and/or current (AMPS label) as well as displacement (U label) and/or force (F label). You may include linear and nonlinear effects. See Chapter 5, “Transient Dynamic Analysis” in the ANSYS Structural Analysis Guide for general information on performing a full transient analysis.

7.8.1.7. Electromechanical Circuit Simulation

The TRANS126 element can be used to model “reduced order” electromechanical devices in a coupled circuit simulation. The ANSYS Circuit Builder (see Chapter 15, “Electric Circuit Analysis” in ANSYS Low-Frequency Electromagnetic Analysis Guide) provides a convenient tool for constructing a reduced order model consisting of linear circuit elements (CIRCU124), mechanical spring, mass, and damper elements (COMBIN14, MASS21, and COMBIN39), and the electromechanical transducer element (TRANS126). TRANS126 links the electrical and mechanical models. Static, harmonic, and transient analysis of electromechanical circuit models may be performed.

7.8.2. The 2-D Transducer Element

You can analyze MEMS devices using distributed models consisting of mechanical elements and the electromechanical transducer element TRANS109. The transducer element converts energy from an electrostatic domain into a mechanical domain. It represents the capacitive response of a device to motion in two directions, assuming negligible displacements in the out-of-plane direction. It is assumed that the thickness of the element is constant as the domain deforms (plane strain analysis). The out-of-plane thickness may be input by a real constant. TRANS109 has no built-in contact feature, but it can be used in conjunction with traditional contact elements.

TRANS109 complements the ANSYS Multi-field solver and TRANS126 capabilities. TRANS109 is strongly coupled, like TRANS126, but it models the geometry of the 2-D air region like the ANSYS Multi-field solver. Table 7.7: “Methods of Analyzing Electromechanical Coupling” summarizes the capabilities.

Table 7.7 Methods of Analyzing Electromechanical Coupling

<table>
<thead>
<tr>
<th>Feature</th>
<th>ANSYS Multi-field solver</th>
<th>TRANS126</th>
<th>TRANS109</th>
</tr>
</thead>
<tbody>
<tr>
<td>Geometry</td>
<td>2-D, 3-D</td>
<td>1-D</td>
<td>2-D</td>
</tr>
</tbody>
</table>
During the solution, TRANS109 morphs the initial mesh. Both area weighted and unweighted morphing methods are available. Weighted morphing generally provides better mesh quality, but may converge slower. The unweighted method is recommended when morphing does not significantly change the shape of the transducer elements.

At equilibrium, the electrostatic force between transducer and mechanical elements balance each other. The TRANS109 mesh deforms so that the force equilibrium can be obtained. TRANS109 internally morphs the mesh. No new nodes or elements are created during morphing, but the positions of the original nodes are constantly updated according to the electromechanical force balance. You can take advantage of the TRANS109 mesh morphing to avoid recreating the solid model and remeshing during parametric studies. New geometries can be created simply by applying nonzero displacement constraints.

TRANS109 will not work with the elements CIRCU94, CIRCU124, CIRCU125, INFIN110, PLANE121, or TRANS126.

Relative dielectric permittivity is input using the MP command with the PERX label. Temperature dependent permittivity is not supported.

TRANS109 allows large deformations, activated by NLGEOM,ON. Nonlinear analysis can exploit the full system tangent stiffness matrix. Stiffness, nodal forces, and charges are computed on a per-length basis. TRANS109 works with Frontal, Sparse, ICCG, JCG or PCG solvers. TRANS109 does not support solution control.

Loading follows usual ANSYS procedure, including solid model boundary conditions. When applying nonzero loads on the VOLT DOF, it is recommended that the DOF be initialized to the same nonzero value using the IC command. Charge density surface and body loads are not supported. Loading may be ramped using the NSUBST and KBC,0 commands. Automatic time and load stepping may be invoked using AUTOTS,ON.

### 7.8.2.1. Element Physics

TRANS109 is a fully coupled 2-D triangular transducer element which relates the electrostatic response and the structural response of an electromechanical device. Because the element is fully coupled, you can use it effectively in coupled electromechanical static and transient analyses.

The electrostatic energy is given by:

\[ W = \frac{1}{2} (V) (C) (V) \]

where the term \((V)\) is the vector of nodal voltages and the term \((C)\) is the element capacitance matrix.

The vector of electrostatic charges, \((Q)\), the electric reaction, is given by:
Q = (C) (V)

The capacitance matrix (C) depends on the element geometry.

The nodal electrostatic reaction forces can be calculated by the virtual work principle:

$$ F = (1/2) \frac{dW}{dU} $$

where the term (U) is a nodal displacement.

As can be seen from the above equations, the capacitance of the device over a range of motion characterizes the electromechanical response of the device. Refer to the ANSYS Elements Reference and the ANSYS, Inc. Theory Reference for a full description of the TRANS109 element.

### 7.8.2.2. Static Analysis

The static equilibrium of an electrostatic transducer may be unstable. With increasing voltage, the attraction force between the capacitor plates increases and the gap decreases. For a gap distance d, the spring restoring force is proportional to 1/d and the electrostatic force is proportional to 1/d^2. When the capacitor gap decreases to a certain point, the electrostatic attraction force becomes larger than the spring restoring force and the capacitor plates snap together. Subsequently, when the capacitor voltage decreases to a certain value, the electrostatic attraction force becomes smaller than the spring restoring force and the capacitor plates snap apart.

The transducer element can exhibit hysteresis as shown in Figure 7.4: “Electromechanical Hysteresis”. The voltage ramps up to the pull-in value and then back down to the release value.

The transducer element by nature has both stable and unstable solutions as shown in Figure 7.5: “Static Stability Characteristics”. The element will converge to either solution depending on the starting location (initial gap size).

### 7.8.2.3. Transient Analysis

A full transient analysis may be run incorporating a transducer element (TRANS109) attached to a complex finite element structure. You can apply any arbitrary large-signal time-varying excitation to the transducer or structure to produce a fully-coupled transient electromechanical response. You can apply both voltage and current as electrical loads, and you can apply displacement or force as mechanical loads. Use the IC command to specify both the initial voltage and voltage rate (using the VALUE1 and VALUE2 fields), as well as displacement and velocity. You may include nonlinear effects. See Chapter 5, “Transient Dynamic Analysis” in the ANSYS Structural Analysis Guide for general information on performing a full transient analysis.

### 7.8.2.4. Problem Analysis

Usually TRANS109 solves the coupled electrostatic-structural problem easily. However, in certain situations convergence problems may occur. This section attempts to summarize typical problem cases and provide methods to avoid or ease the problems. You may encounter the following two kinds of solution error messages using TRANS109:

- inverted element
- unconverged solution

An inverted element error message indicates that mesh morphing created a severely distorted element. An unconverged solution error indicates that ANSYS failed to converge to an acceptable solution. The following sections discuss various problems that may be encountered with the TRANS109 element.
### 7.8.2.4.1. Under-Constrained Model

An under-constrained model is one source of inverted elements. Displacement constraints are necessary on air boundary nodes. To resolve this problem, apply displacement constraints normal to the boundary at the air truncation nodes.

### 7.8.2.4.2. Bifurcation, Buckling, or Pulling In

In a static analysis, when a voltage larger than the pull-in voltage is applied to the electrodes, the electrodes attempt to “snap” together, and no stable configuration can be found. To obtain stable solutions prior to pull-in, apply auto time stepping and load ramping using the `AUTOTS` and `NSUBST` commands. Save each substep result with the `OUTRES` command. This process may terminate in an unconverged solution, but the auto time stepping process should pick up the peak, the last converged solution, and all stable solutions below buckling. Use the general postprocessor to review these results.

To obtain a solution beyond the pull-in voltage, see the next section.

### 7.8.2.4.3. Post-Buckling or Release

To determine the release voltage, start with a voltage larger that the pull-in voltage. As the voltage is decreased, at the release voltage the solution jumps back to the stable region.

To start the analysis with the electrodes in contact, ground the electrodes using `D,VOLT,0`, set the displacement solution near the expected pulled-in state, apply `D,UX` and `D,UY` commands, and solve. So that previous results act like initial conditions, do not leave the solution processor. Apply the required voltage load on the electrodes using `D,VOLT`, remove displacement constraints artificially applied in the previous step using the `DDELE` command, and solve.

Alternatively, apply initial displacement conditions consistent with the pull-in solution using the `IC` command.

### 7.8.2.4.4. Dynamic Pull-in and Release or Hysteresis

The voltage applied to the electrodes is increased beyond pull-in voltage then decreased below the release voltage in a transient analysis. This increase and decrease may be repeated several times since, typically, the pull-in and release voltages differ. The result is “walking around” a hysteresis loop.

To resolve this problem, decrease the minimum time step using the `DELTIM` command. Use auto time stepping to monitor convergence and increase or decrease the time step according to needs.

### 7.8.2.4.5. Unconverged Solution with Decreasing Convergence Norm

The ANSYS solution ends with an unconverged solution error message despite a decreasing error norm. The problem is probably that convergence criteria are so strict that the convergence norm does not decrease below the requested level within the given number of equilibrium iterations.

To resolve this problem, relax the convergence criteria or increase the number of allowed equilibrium iterations using the `CNVTOL` and `NEQIT` commands. To postprocess the unconverged or last converged solution, use the `SET` command.

### 7.8.2.4.6. Coarse Mesh and Convergence Norm Diverges

In this scenario, the convergence norm first decreases and then increases resulting in an inverted element or unconverged solution error message. The desired convergence tolerance cannot be reached, and increasing the
number equilibrium iterations, finer ramping of the loads, or better initial conditions do not help. This indicates that the given mesh is not fine enough.

To resolve this problem, refine the mesh, especially near corners and edges. Verify residual electrostatic forces using the \texttt{FSUM} and \texttt{RFORCE} commands.

\section*{7.9. Sample Thermoelectric Cooler Analysis (Batch or Command Method)}

This example problem considers the performance of a thermoelectric cooler described in \textit{Direct Energy Conversion} (Third Edition) by Stanley W. Angrist, Ch. 4, p.161 (1976).

\subsection*{7.9.1. Problem Description}

A thermoelectric cooler consists of two semiconductor elements connected by a copper strap. One element is an \textit{n}-type material and the other is a \textit{p}-type material. The \textit{n}-type and \textit{p}-type elements have a length \( L \), and a cross-sectional areas \( A = W^2 \), where \( W \) is the element width. The cooler is designed to maintain the cold junction at temperature \( T_c \), and to dissipate heat from the hot junction \( T_h \) on the passage of an electric current of magnitude \( I \). The positive direction of the current is from the \textit{n}-type material to the \textit{p}-type material as shown in the following figure.

\begin{figure}[h]
\centering
\includegraphics[width=0.5\textwidth]{thermoelectric_cooler.png}
\caption{Thermoelectric Cooler}
\end{figure}

\textit{Note} — The dimensions of the copper strap were chosen arbitrarily. See the command input listing for the dimensions used. The effect on the results is negligible.

The semiconductor elements have the following dimensions:

- Length \( L = 1 \text{ cm} \)
- Width \( W = 1 \text{ cm} \)
- Cross-sectional area \( A = 1 \text{ cm}^2 \)

The thermoelectric cooler has the following material properties.
### Table 7.8 Material Properties

<table>
<thead>
<tr>
<th>Component</th>
<th>Resistivity (ohm*cm)</th>
<th>Thermal Conductivity (watt/cm°C)</th>
<th>Seebeck Coefficient (µvolts/°C)</th>
</tr>
</thead>
<tbody>
<tr>
<td>n-type material</td>
<td>$\rho_n = 1.05 \times 10^{-3}$</td>
<td>$\lambda_n = .013$</td>
<td>$\alpha_n = -165$</td>
</tr>
<tr>
<td>p-type material</td>
<td>$\rho_p = 0.98 \times 10^{-3}$</td>
<td>$\lambda_p = .012$</td>
<td>$\alpha_p = 210$</td>
</tr>
<tr>
<td>Connecting straps (copper)</td>
<td>1.7 x 10^{-6}</td>
<td>400</td>
<td>—</td>
</tr>
</tbody>
</table>

### First Thermal-Electric Analysis

A 3-D steady-state thermal-electric analysis is carried out to evaluate the performance of the cooler. The givens are: $T_c = 0^\circ C$, $T_h = 54^\circ C$, and $I = 28.7$ amps. The following quantities are calculated and compared to analytical values.

1. The heat rate $Q_c$ that must be pumped away from the cold junction to maintain the junction at $T_c$:

   $$Q_c = \alpha T_c I - 1/2 I^2 R - K \Delta T$$

   where:
   - Combined Seebeck coefficient $\alpha = |\alpha_n| + |\alpha_p|$
   - Internal electrical resistance $R = (\rho_n + \rho_p) L / A$
   - Internal thermal conductance $K = (\lambda_n + \lambda_p) A / L$
   - Applied temperature difference $\Delta T = T_h - T_c$

2. The power input:

   $$P = VI = \alpha I (\Delta T) + I^2 R$$

   where:
   - $V$ = voltage drop across the cooler

3. The coefficient of performance:

   $$\beta = Q_c / P$$

### Second Thermal-Electric Analysis

The inverse problem is solved. The givens are: $Q_c = 0.74$ watts, $T_h = 54^\circ C$, and $I = 28.7$ amps and the cold junction temperature $T_c$ and the temperature distribution are determined.
7.9.2. Expected Results

The first thermal-electric analysis is performed by imposing a temperature constraint $T_c = 0 \, ^\circ\text{C}$ on the cold junction and an electric current $I$ on the input electric terminal. The rate of heat removed from the cold junction $Q_c$ is determined as a reaction solution at the master node. The input power $P$ is determined from the voltage and current at the input terminal. The coefficient of performance is calculated from $Q_c$ and $P$. Numerical results are compared in Table 7.9: “Thermoelectric Cooler Results” to the analytical design from the reference. A small discrepancy between the numerical and analytical results is due to the presence of the connecting straps.

<table>
<thead>
<tr>
<th>Quantity</th>
<th>ANSYS Results</th>
<th>Reference Results</th>
</tr>
</thead>
<tbody>
<tr>
<td>$Q_c$, watts</td>
<td>0.726</td>
<td>0.74</td>
</tr>
<tr>
<td>$P$, watts</td>
<td>2.293</td>
<td>2.35</td>
</tr>
<tr>
<td>$\beta$</td>
<td>0.317</td>
<td>0.32</td>
</tr>
</tbody>
</table>

In the second analysis, an inverse problem is solved: $Q_c$ from the first solution is imposed as a rate of heat flow on the cold junction to determine the temperature at that junction. The calculated temperature of the cold junction $T_c = 0.0984 \, ^\circ\text{C}$ is close to the expected 0 $^\circ\text{C}$. The following figure shows the temperature distribution.
7.9.3. Command Listing

/title, Thermoelectric Cooler
/com
/com Reference: "Direct Energy Conversion" (third edition) by Stanley W. Angrist
/com Ch.4 "Thermoelectric Generators", p. 164
/com
/VUP,1,z
/VIEW,1,1,1,1
/TRIAD,OFF
/NUMBER,1
/ENUM, MAT, 1
/nopr

/PREP7
! cooler dimensions
l=1e-2 ! element length, m
w=1e-2 ! element width, m
hs=0.1e-2 ! strap height, m

toffst,273 ! Temperature offset, deg.C

! n-type material
mp,rsvx,1,1.05e-5 ! Electrical resistivity, Ohm*m
mp,kxx,1,1.3 ! Thermal conductivity, watt/(m*K)
mp,sbkx,1,-165e-6 ! Seebeck coefficient, volt/K

! p-type material
mp,rsvx,2,0.98e-5 ! Electrical resistivity, Ohm*m
mp,kxx,2,1.2 ! Thermal conductivity, watt/(m*K)
mp,sbkx,2,210e-6 ! Seebeck coefficient, volt/K

! Connecting straps (copper)
mp,rsvx,3,1.7e-8 ! Resistivity, Ohm*m
mp,kxx,3,400 ! Thermal conductivity, Watt/(m*K)

! FE model
et,1,226,110 ! 20-node thermo-electric brick
et,2,227,110 ! 10-node thermo-electric tet
! Boundary conditions and loads
nsel,s,loc,z,l+hs    ! Cold junction
cp,1,temp,all        ! Couple TEMP dofs
nc=ndnext(0)         ! Get master node number
nsel,s,loc,z,-hs     ! Hot junction
d,all,temp,54        ! Hold at Th, deg. C

nsel,s,loc,x,-1.7*w  ! First electric terminal
d,all,volt,0         ! Ground

nsel,s,loc,x,1.7*w   ! Second electric terminal
cp,2,volt,all       ! Couple VOLT dofs
ni=ndnext(0)         ! Get master node
nsel,all
fini

/SOLU                 ! First solution
antype,static
d,nc,temp,0           ! Hold cold junction at Tc, deg.C
I=28.7
f,ni,amps,I           ! Apply current I, Amps to the master node
solve
fini

*get,Qc,node,nc,rf,heat  ! Get heat reaction at cold junction
/com
Heat absorbed at the cold junction Qc = %Qc%, watts
/com
P=volt(ni)*I          ! Power input P = %P%, watts
/com
Coefficient of performance beta = %Qc/P%
/com

/SOLU                 ! Second solution
ddele,nc,temp         ! Delete TEMP dof constraint at cold junction
f,nc,heat,Qc          ! Apply heat flow rate Qc to the cold junction
solve
fini

/com
Temperature at the cold junction Tc = %temp(nc)% deg.C
/com

/SHOW,WIN32c           ! Use /SHOW,X11C for UNIX
7.10. Sample Thermoelectric Generator Analysis (Batch or Command Method)

This example problem considers the performance of a power producing thermoelectric generator described in Direct Energy Conversion (Third Edition) by Stanley W. Angrist, Ch. 4, p.156 (1976).

7.10.1. Problem Description

A thermoelectric generator consists of two semiconductor elements. One element is an n-type material and the other is a p-type material. The n-type and p-type elements have lengths $L_n$ and $L_p$ and cross-sectional areas $A_n = W_n t$ and $A_p = W_p t$, where $W_n$ and $W_p$ are the element widths and $t$ is the element thickness. The generator operates between temperature $T_c$ (a cold junction) and temperature $T_h$ (a hot junction). The hot sides of the elements are coupled in temperature and voltage. The cold sides of the elements are connected to an external resistance $R_o$. The temperature difference between the cold and hot sides generates electric current $I$ and power $P_o$ in the load resistance.

![Figure 7.9 Thermoelectric Generator](image)

The semiconductor elements have the following dimensions.

<table>
<thead>
<tr>
<th>Table 7.10 Semiconductor Element Dimensions</th>
</tr>
</thead>
<tbody>
<tr>
<td>Dimension</td>
</tr>
<tr>
<td>Length L</td>
</tr>
<tr>
<td>Width W</td>
</tr>
<tr>
<td>Thickness t</td>
</tr>
</tbody>
</table>

The operating conditions are:

- Cold junction temperature $T_c = 27^\circ$C
- Hot junction temperature $T_h = 327^\circ$C
Two 3-D steady-state thermal-electric analyses are performed to evaluate the thermal efficiency of the generator.

**First Thermal-Electric Analysis**

A thermal-electric analysis is performed using the following material properties at the average temperature of $177^\circ C$ (Angrist, Ch.4, p.157).

<table>
<thead>
<tr>
<th>Component</th>
<th>Resistivity (ohm$^\ast$cm)</th>
<th>Thermal Conductivity (watt/cm°C)</th>
<th>Seebeck Coefficient (µvolts/°C)</th>
</tr>
</thead>
<tbody>
<tr>
<td>n-type material</td>
<td>$\rho_n = 1.35 \times 10^{-3}$</td>
<td>$\lambda_n = 0.014$</td>
<td>$\alpha_n = -195$</td>
</tr>
<tr>
<td>p-type material</td>
<td>$\rho_p = 1.75 \times 10^{-3}$</td>
<td>$\lambda_p = 0.012$</td>
<td>$\alpha_p = 230$</td>
</tr>
</tbody>
</table>

The following quantities are calculated and compared to the analytical values.

1. The thermal input to the hot junction:

   \[ Q_h = \alpha T_h I - \frac{1}{2} I^2 R + K \Delta T \]

   where:
   - Combined Seebeck coefficient $\alpha = |\alpha_n| + |\alpha_p|$
   - Internal electrical resistance $R = \rho_n (L_n/ A_n) + \rho_p (L_p/ A_p)$
   - Internal thermal conductance $K = \lambda_n (A_n/ L_n) + \lambda_p (A_p/ L_p)$
   - Applied temperature difference $\Delta T = T_h - T_c$

2. The electric current:

   \[ I = \frac{\alpha \Delta T}{(R + R_o)} \]

3. The output power:

   \[ P_o = I^2 R_o \]

4. The thermal efficiency:

   \[ \eta = \frac{P_o}{Q_h} \]

**Second Thermal-Electric Analysis**

This is the same as the first analysis, except that the temperature dependence of the Seebeck coefficient, electrical resistivity, and thermal conductivity of the materials is taken into account using the following data (Angrist, Appendix C, p.476–477).
**Figure 7.10 Temperature Dependent Material Properties**

<table>
<thead>
<tr>
<th>n-type Material</th>
<th>p-type Material</th>
</tr>
</thead>
<tbody>
<tr>
<td><img src="image1.png" alt="Graph 1" /></td>
<td><img src="image2.png" alt="Graph 2" /></td>
</tr>
<tr>
<td><img src="image3.png" alt="Graph 3" /></td>
<td><img src="image4.png" alt="Graph 4" /></td>
</tr>
</tbody>
</table>
7.10.2. Expected Results

The following table shows the results using material properties at the average temperature of 177°C.

**Table 7.12 Results Using Material Properties at Average Temperature**

<table>
<thead>
<tr>
<th>Quantity</th>
<th>ANSYS Results</th>
<th>Reference Results</th>
</tr>
</thead>
<tbody>
<tr>
<td>$Q_h$, watts</td>
<td>13.03</td>
<td>13.04</td>
</tr>
<tr>
<td>$I$, amps</td>
<td>19.08</td>
<td>19.2</td>
</tr>
<tr>
<td>$P_o$, watts</td>
<td>1.43</td>
<td>1.44</td>
</tr>
<tr>
<td>$\eta$, %</td>
<td>10.96</td>
<td>10.95</td>
</tr>
</tbody>
</table>

The following table shows the results when temperature dependence of the material properties is taken into account.

**Table 7.13 Results Considering Material Temperature Dependence**

<table>
<thead>
<tr>
<th>Quantity</th>
<th>ANSYS Results</th>
</tr>
</thead>
<tbody>
<tr>
<td>$Q_h$, watts</td>
<td>11.07</td>
</tr>
<tr>
<td>$I$, amps</td>
<td>16.37</td>
</tr>
<tr>
<td>$P_o$, watts</td>
<td>1.05</td>
</tr>
<tr>
<td>$\eta$, %</td>
<td>9.49</td>
</tr>
</tbody>
</table>

7.10.3. Command Listing

```
/title, Thermoelectric Generator
/com
/com Reference: "Direct Energy Conversion" (3rd edition) by
```
! Generator dimensions
ln=1.e-2                 ! n-type element length, m
lp=1.e-2                 ! p-type element length, m
wn=1.e-2                 ! n-type element width, m
wp=1.24e-2               ! p-type element width, m
t=1.e-2                  ! element thickness, m
d=0.4e-2                 ! Distance between the elements

rsvn=1.35e-5             ! Electrical resistivity, Ohm*m
rsvp=1.75e-5
kn=1.4                   ! Thermal conductivity, Watt/(m*K)
kp=1.2
sbkn=-195e-6             ! Seebeck coeff, volt/deg, n-type
sbkp=230e-6              !                          p-type
Th=327                   ! Temperature of hot junction, deg.C
Tc=27                    ! Temperature of cold side, deg.C
Toffst=273               ! Temperature offset, deg.C
R0=3.92e-3               ! External resistance, Ohm

/nopr
/PREP7
et,1,SOLID226,110        ! 20-node thermoelectric brick
/com
/com *** Thermo-electric analysis with material
/com *** properties evaluated at an average temperature
/com
! Material properties for n-type material
mp,rsvx,1,rsvn
mp,kxx,1,kn
mp,sbkx,1,sbkn

! Material properties for p-type material
mp,rsvx,2,rsvp
mp,kxx,2,kp
mp,sbkx,2,sbkp

! Solid model
block,d/2,wn+d/2,-ln,0,,t
block,-(wp+d/2),-d/2,-lp,0,,t

! Meshing
esize,wn/2
mat,1
vmesh,1
mat,2
vmesh,2
toffst,Toffst            ! Temperature offset

! Boundary conditions and loads
nsel,s,loc,y,0           ! Hot side
cp,1,temp,all            ! couple TEMP dofs
nh=ndnext(0)             ! Get master node
d,nh,temp,Th             ! Set TEMP constraint to Th
cp,2,volt,all            ! couple VOLT dofs
nsel,all

nsel,s,loc,y,-ln          ! Cold side, n-type
nsel,r,loc,x,d/2,wn+d/2
d,all,temp,Tc
cp,3,volt,all            ! Input electric terminal
nn=ndnext(0)             ! Get master node
nsel,all

nsel,s,loc,y,-lp          ! Cold side, p-type
nsel,r,loc,x,-(wp+d/2),-d/2
d,all,temp,Tc
cp,4,volt,all            ! Output electric terminal
np=ndnext(0) ! Get master node
nsel,all
d,np,volt,0 ! Ground
et,2,CIRCU124,0 ! Load resistor
r,1,R0
type,2
real,1
e,np,nn
fini
/SOLU
antype,static
cnvtol,heat,1,1.e-3 ! Set convergence values
cnvtol,amps,1,1.e-3 ! for heat flow and current
solve
fini

! n-branch area
An=wn*t
! p-branch area
Ap=wp*t
! Total thermal conductance
K=kp*Ap/lp+kn*An/ln
! Total electric resistance of the couple
R=lp*rsvp/An+ln*rsvn/An
! Combined Seebeck coefficient
alp=abs(sbkp)+abs(sbkn)
/com
\com *** Calculated and expected results:
/com
\com Heat pumping rate on cold side Qh, Watts
*get,Qh,node,nh,rf,heat
\com - ANSYS: %Qh%
I_a=alp*(Th-Tc)/(R+R0)
Qh_a=alp*I_a*(Th+Toffst)-I_a**2*R/2+K*(Th-Tc)
\com - Expected: %Qh_a%
/com
\com Electric current I drawn from the generator, Amps
*get,I,elem,21,smisc,2
\com - ANSYS: %I%
\com - Expected: %I_a%
/com
\com Output power P, Watts
*get,P0,elem,21,nmisc,1
\com - ANSYS: %P0%
P0_a=I_a**2*R0
\com - Expected: %P0_a%
/com
\com Coefficient of thermal efficiency
\com - ANSYS: %P0/Qh%
\com - Expected: %P0_a/Qh_a%
/com
\com *** Thermo-electric analysis with temperature
\com *** dependent material properties
/com
/PREP7
\com Temperature data points
mptmp,1,25,50,75,100,125,150
mptmp,7,175,200,225,250,275,300
mptmp,13,325,350

! n-type material
! Seebeck coefficient, Volt/K
mpdata,abxx,1,1,-160e-6,-168e-6,-174e-6,-180e-6,-184e-6,-187e-6
mpdata,abxx,1,7,-189e-6,-190e-6,-189e-6,-186.5e-6,-183e-6,-177e-6
mpdata,abxx,1,13,-169e-6,-160e-6
mmpplot,abxx,1
Section 7.11: Sample Structural-Thermal Harmonic Analysis (Batch or Command Method)

In this example, a harmonic analysis is performed to calculate the effect of thermoelastic damping in a thin silicon beam vibrating transversely. The thermoelastic damping, or "internal friction," arising from the irreversible heat flow across the temperature gradients induced by the strain field in vibrating reeds has been predicted and investigated by C. Zener in "Internal Friction in Solids" published in Physical Review, Vol. 52, (1937), p.230 and Vol. 53, (1938), p.90.
7.11.1. Problem Description

A thin silicon clamped-clamped beam of length $L = 300 \mu m$ and width $W = 5 \mu m$ vibrates transversely under a uniform pressure $P = 0.1 \text{ MPa}$ applied in the -$Y$ direction. The beam temperature in equilibrium is $T_0 = 27 ^\circ C$.

![Clamped-clamped Beam](image1)

The material properties used in the analysis are listed in the following table.

<table>
<thead>
<tr>
<th>Material Property</th>
<th>Value (µMKSV)</th>
</tr>
</thead>
<tbody>
<tr>
<td>Young's Modulus</td>
<td>$1.3 \times 10^5 \text{ MPa}$</td>
</tr>
<tr>
<td>Poisson's Ratio</td>
<td>0.28</td>
</tr>
<tr>
<td>Density</td>
<td>$2.23 \times 10^{-15} \text{ kg/(µm)}^3$</td>
</tr>
<tr>
<td>Thermal Conductivity</td>
<td>$9.0 \times 10^7 \text{ pW/(µm*K)}$</td>
</tr>
<tr>
<td>Specific Heat</td>
<td>$6.99 \times 10^{14} \text{ pJ/(kg*K)}$</td>
</tr>
<tr>
<td>Thermal Expansion Coefficient</td>
<td>$7.8 \times 10^{-6} \text{ 1/K}$</td>
</tr>
</tbody>
</table>

The beam finite element model is built using plane stress thermoelastic analysis options on the PLANE223 coupled-field element. A structural-thermal harmonic analysis is performed in the frequency range between 10 kHz and 10 MHz that spans the first six resonant modes of the beam.

7.11.2. Expected Results

The thermoelastic damping $Q^{-1}$ is calculated using the equation given in Thermoelasticity in the ANSYS, Inc. Theory Reference. The following figure compares the numerical results with Zener's analytical expression for the thermoelastic damping in transversely vibrating reeds.
7.11.3. Command Listing

/title, Thermoelastic Damping in a Silicon Beam, uMKSV system of units
/com,
/com, Reference for the analytical solution:
/com, C. Zener, "Internal Friction in Solids,"
/com,
/nopr

  Material constants for silicon [100]
  
  E=1.3e5 ! Young's modulus, MPa
  nu=0.28 ! Poisson's ratio
  k=90e6 ! Thermal conductivity, pW/(um*K)
  rho=2330e-18 ! Density, kg/(um)**3
  Cp=699e12 ! Heat capacity, pJ/(kg*K)
  alp=7.8e-6 ! Thermal expansion, 1/K

  Dimensions
  L=300 ! Length, um
  W=5 ! Width, um

  Loads
  !
  t0=27 ! Reference temperature, C
  Toff=273 ! Offset temperature, K
  P=0.1 ! Pressure, MPa

  Analysis parameters
  !
  fmin=0.1e6 ! Start frequency, Hz
  fmax=10e6 ! End frequency, Hz
  nsbs=100 ! Number of substeps

  Build finite element model
  !
  /PREP7
mp, EX, 1, E
mp, PRXY, 1, NU
mp, DENS, 1, rho
mp, ALPX, 1, ALP
mp, KXX, 1, k
mp, C, 1, Cp

et, 1, PLANE223, 11  ! Thermoelastic plane stress
rect, 1, L, W
esize, W/2
amesh, 1

nsel, s, loc, x, 0  ! Clamp beam ends
nsel, a, loc, x, L
d, all, UX, 0
nsel, r, loc, y, 0
d, all, UY, 0
nsel, all

Tref, t0  ! Set reference temperature
Toffst, Toff  ! Set offset temperature
fini

/com,
/com, == Perform thermoelastic harmonic analysis
/com,

/solu
antyp, harmonic  ! Harmonic analysis
outres, all, all  ! Write all solution items to the database
harfrq, fmin, fmax  ! Specify frequency range
nsubs, nsbs  ! Set number of substeps
nsel, s, loc, y, W
sf, all, pres, P  ! Apply pressure load
nsel, all
kbc, 1  ! Stepped loading
solve
fini
!
! Prepare for Zener's analytical solution
!
delta = E*ALP**2*(t0+Toff)/(rho*Cp)
pi = acos(-1)
tau = rho*Cp*W**2/(k*pi**2)
f_Qmin = 1/(2*pi*tau)
/com,
/com, Frequency of minimum Q-factor: f_Qmin=%f_Qmin%
/com,
f_0 = 0.986
f_1 = 0.012
f_2 = 0.0016
tau0 = tau
tau1 = tau/9
tau2 = tau/25
!
*dim, freq, table, nsbs
*dim, Q, table, nsbs, 2
!
! Post-process solution
!
/post1
df = (fmax - fmin)/nsbs
f = fmin + df
*do, i, 1, nsbs
set,,,, 0, f  ! Read real solution at frequency f
etab, w_r, nmisc, 4
set,,,, 1, f  ! Read imaginary solution at frequency f
etab, w_i, nmisc, 4
ssum
*get, Wr, ssum, item, w_r
*get, Wi, ssum, item, w_i
Qansys = Wr/Wi  ! Numerical quality factor
7.12. Sample Electro-Thermal Microactuator Analysis (Batch or Command Method)


7.12.1. Problem Description

The actuator silicon structure is comprised of a thin arm connected to a wide arm, flexure, and two anchors as shown in the figure below. In addition to providing mechanical support, the anchors also serve as electrical and thermal connections. The actuator operates on the principle of differential thermal expansion between the thin and wide arms. When a voltage difference is applied to the anchors, current flows through the arms producing Joule heating. Because of the width difference, the thin arm of the microactuator has a higher electrical resistance than the wide arm, and therefore it heats up more than the wide arm. The non-uniform Joule heating produces a non-uniform thermal expansion, and actuator tip deflection.

A 3-D static structural-thermoelectric analysis is performed to determine the tip deflection and temperature distribution in the microactuator when a 15 volt difference is applied to the anchors. Radiative and convective surface heat transfers are also taken into account, which is important for accurate modeling of the actuator. The microactuator dimensions (device D2 in the reference) and material properties of doped single-crystal silicon used for the simulation were taken from the reference above. The temperature dependent convective heat losses were applied to all the actuator surfaces; however, they may have been applied in a different way than in the reference.
7.12.2. Results

The tip deflection is determined to be 27.8 µm. The temperature ranges from 300 to 800 K. Displacement and temperature results are shown in the following figures.
Figure 7.14 Microactuator Displacements

Figure 7.15 Microactuator Temperatures
7.12.3. Command Listing

/title, Electro-Thermal Microactuator
/nop2

d1=40e-6               ! Microactuator dimensions, m

d2=259e-6

d3=40e-6

d4=330e-6

d5=1900e-6

d6=90e-6

d7=75e-6

d8=352e-6

d9=352e-6

d11=20e-6

! === Loads
Vlt=15                 ! Voltage difference, Volt
Tblk=300               ! Bulk temperature, K

/VVIEW,1,1,2,3
/PREP7

et,1,SOLID227,111      ! Structural-thermoelectric tetrahedron

! === Material properties
mp,EX,1,169e9          ! Young modulus, Pa
mp,PRXY,1,0.3          ! Poisson's ratio
mp,RSVX,1,4.2e-4       ! Electrical resistivity, Ohm-m

! Temperature table for ALPX and KXX
mptemp,1,300,400,500,600,700,800
mptemp,7,900,1000,1100,1200,1300,1400
mptemp,13,1500

! Coefficients of thermal expansion data table, 1/K
mpdata,ALPX,1,1,2.568e-6,3.212e-6,3.594e-6,3.831e-6,3.987e-6,4.099e-6
mpdata,ALPX,1,7,4.185e-6,4.258e-6,4.323e-6,4.384e-6,4.442e-6,4.5e-6
mpdata,ALPX,1,13,4.556e-6

! Thermal conductivity data table, W/(m-K)
mpdata,KXX,1,1,146.4,98.3,73.2,57.5,49.2,41.8
mpdata,KXX,1,7,37.6,34.5,31.4,28.2,27.2,26.1
mpdata,KXX,1,13,25.1

trref,Tblk            ! Reference temperature

! === Solid model
k,1,0,0               ! Define keypoints
k,2,0,d9
k,3,d8,d9
k,4,d8,d1
k,5,d8+d4+d5,d1
k,6,d8+d4+d5,-(d7+d2)
k,7,d8+d4, -(d7+d2)
k,8,d8+d4, -(d7+d3)
k,9,d8, -(d7+d3)
k,10,d8, -(d7+d9)
k,11,0, -(d7+d9)
k,12,0, -d7
k,13,d8+d4+d5-d6,-d7
k,14,d8+d4+d5-d6,0

a,1,2,3,4,5,6,7,8,9,10,11,12,13,14 ! Define area
vext,1,1,3,111       ! Extrude area by the out-of-plane size

! === Finite element model
isel,s,line,,31,42   ! Element size along out-of-plane dimension
lesize,all,d11
isel,s,line,,1,3    ! Element size along anchor sides
isel,a,line,,9,11
isel,a,line,,15,17
isel,a,line,,23,25
lesize,all,d9/2
isel,s,line,,5       ! Element size along side walls
isel,a,line,,19
lesize,all,(d1+d2+d7)/6
isel,s,line,,13      ! Element size along the end connection
isel,a,line,,27

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lesize, all, d7/3
lsel, s, line,, 8   ! Element size along the flexure
lsel, a, line,, 22
lesize, all, d4/6
lsel, s, line,, 4   ! Element size along the thin arm
lsel, a, line,, 18
lesize, all, (d4+d5)/30
lsel, s, line,, 14
lsel, a, line,, 28
lesize, all, (d8+d4+d5-d6)/40
lsel, s, line,, 7   ! Element size along the wide arm
lsel, a, line,, 21
lesize, all, d2/5
lsel, s, line,, 12
lsel, a, line,, 26
lesize, all, (d8+d4+d5-d6)/35
lsel, s, line,, 6
lsel, a, line,, 20
lesize, all, d5/25
lsel, all
vmesh, 1           ! Mesh the volume

! === DOF constraints on the anchors
nsel, s, loc, x, 0, d8
nsel, r, loc, z, 0   ! Bottom surface
d, all, UX, 0, ..., UY, UZ
d, all, TEMP, Tblk
nsel, all

nsel, s, loc, x, 0, d8
nsel, r, loc, y, -(d7+d9), -d7
cp, 1, VOLT, all
n_gr=ndnext(0)
d, n_gr, VOLT, 0
nsel, s, loc, x, 0, d8
nsel, r, loc, y, 0, d9
cp, 2, VOLT, all
n_vlt=ndnext(0)
d, n_vlt, VOLT, Vlt
nsel, all

! === Radiosity boundary conditions
sf, all, RDSF, 0.7, 1   ! Surface-to-surface radiation load
spctemp, 1, Tblk        ! Ambient temperature
stef, 5.6704e-8         ! Stefan–Boltzman radiation constant, J/(K)^4(m)^2(s)

! === Temperature dependent convection boundary conditions
Mptemp               ! Initialize temperature table
! Temperature table for thermal loading
mptemp, 1, 300, 500, 700, 900, 1100, 1300
mptemp, 7, 1500
! === Upper face
asel, s, area,, 2      ! Thin arm and flexure
nsla, s, 1
nsel, r, loc, x, d8, d8+d4+d5-d6
nsel, r, loc, y, 0, d1
sf, all, CONV, -1, Tblk
nsla, s, 1
nsel, r, loc, x, d8, d8+d4
nsel, r, loc, y, -(d3+d7), -d7
sf, all, CONV, -1, Tblk
mpdata, HF, 1, 1, 17.8, 60.0, 65.6, 68.9, 71.1, 72.6
mpdata, HF, 1, 7, 73.2
nsla, s, 1            ! Wide arm
nsel, r, loc, x, d8+d4, d8+d4+d5-d6
nsel, r, loc, y, -(d2+d7), -d7
sf, all, CONV, -2, Tblk
mpdata, HF, 2, 1, 11.2, 37.9, 41.4, 43.4, 44.8, 45.7
mpdata, HF, 2, 7, 46.0
nsla, s, 1            ! End connection
nsel, r, loc, x, d8+d4+d5-d6, d8+d4+d5
sf, all, CONV, -3, Tblk
7.13. Sample Piezoelectric Analysis (Batch or Command Method)

This example problem considers a piezoelectric bimorph beam in actuating and sensing modes.

7.13.1. Problem Description

A piezoelectric bimorph beam is composed of two piezoelectric layers joined together with opposite polarities. Piezoelectric bimorphs are widely used for actuation and sensing. In the actuation mode, on the application of an electric field across the beam thickness, one layer contracts while the other expands. This results in the
bending of the entire structure and tip deflection. In the sensing mode, the bimorph is used to measure an external load by monitoring the piezoelectrically induced electrode voltages.

As shown in Figure 7.16: "Piezoelectric Bimorph Beam", this is a 2-D analysis of a bimorph mounted as a cantilever. The top surface has ten identical electrode patches and the bottom surface is grounded.

In the actuator simulation, perform a linear static analysis. For an applied voltage of 100 Volts along the top surface, determine the beam tip deflection. In the sensor simulation, perform a large deflection static analysis. For an applied beam tip deflection of 10 mm, determine the electrode voltages \( V_1, V_2, \ldots, V_{10} \) along the beam.

**Figure 7.16 Piezoelectric Bimorph Beam**

![Piezoelectric Bimorph Beam Diagram]

\( \downarrow P \) and \( \uparrow P \) indicate the polarization direction of the piezoelectric layer

### 7.13.2. Problem Specifications

The bimorph material is Polyvinylidene Fluoride (PVDF) with the following properties:

- Young's modulus \( (E_1) = 2.0 \times 10^9 \) N/m\(^2\)
- Poisson's ratio \( (\nu_{12}) = 0.29 \)
- Shear modulus \( (G_{12}) = 0.775 \times 10^9 \) N/m\(^2\)
- Piezoelectric strain coefficients \( (d_{31}) = 2.2 \times 10^{-11} \) C/N, \( (d_{32}) = 0.3 \times 10^{-11} \) C/N, and \( (d_{33}) = -3.0 \times 10^{-11} \) C/N
- Relative permittivity at constant stress \( (\varepsilon_{33})^T = 12 \)

The geometric properties are:

- Beam length \( (L) = 100 \) mm
- Layer thickness \( (H) = 0.5 \) mm

Loadings for this problem are:

- Electrode voltage for the actuator mode \( (V) = 100 \) Volts
- Beam tip deflection for the sensor mode \( (U_y) = 10 \) mm

### 7.13.3. Results

#### Actuator Mode

A deflection of \(-32.9 \) \( \mu \)m is calculated for 100 Volts.

\[ U_y = -3(d_{31})(V)(L)^2/(8H)^2 \]

Substituting the problem values gives a theoretical deflection of \(-33.0 \mu m\).

**Sensor Mode**

Electrode voltage results for a 10 millimeter beam tip deflection are shown in Table 7.15: “Electrode 1-5 Voltages” and Table 7.16: “Electrode 6-10 Voltages”. They are in good agreement with those reported by W.-S. Hwang and H.C. Park (“Finite Element Modeling of Piezoelectric Sensors and Actuators,” American Institute of Aeronautics and Astronautics, Vol. 31, No.5, pp. 930-937, 1993).

**Table 7.15 Electrode 1-5 Voltages**

<table>
<thead>
<tr>
<th>Electrode</th>
<th>1</th>
<th>2</th>
<th>3</th>
<th>4</th>
<th>5</th>
</tr>
</thead>
<tbody>
<tr>
<td>Volts</td>
<td>295.2</td>
<td>266.7</td>
<td>235.3</td>
<td>203.8</td>
<td>172.3</td>
</tr>
</tbody>
</table>

**Table 7.16 Electrode 6-10 Voltages**

<table>
<thead>
<tr>
<th>Electrode</th>
<th>6</th>
<th>7</th>
<th>8</th>
<th>9</th>
<th>10</th>
</tr>
</thead>
<tbody>
<tr>
<td>Volts</td>
<td>140.9</td>
<td>109.5</td>
<td>78.2</td>
<td>47.1</td>
<td>18.2</td>
</tr>
</tbody>
</table>

### 7.13.4. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment. An alternative element type and material input are included in the comment lines.

```bash
/batch,list
/title, Static Analysis of a Piezoelectric Bimorph Beam
/nopr
/com,
/PREP7
!
! Define problem parameters
!
! - Geometry
!
! L=100e-3                        ! Length, m
H=0.5e-3                        ! One-layer thickness, m
!
! - Loading
!
V=100                           ! Electrode voltage, Volt
Uy=10.e-3                       ! Tip displacement, m
!
! - Material properties for PVDF
!
E1=2.0e9                        ! Young's modulus, N/m^2
NU12=0.29                       ! Poisson's ratio
G12=0.775e9                     ! Shear modulus, N/m^2
d31=2.2e-11                     ! Piezoelectric strain coefficients, C/N
d32=0.3e-11                     !
d33=-3.0e-11
ep33=12                         ! Relative permittivity at constant stress
!
! Finite element model of the piezoelectric bimorph beam
!
local,11                         ! Coord. system for lower layer: polar axis +Y
```

Chapter 7: Direct Coupled-Field Analysis

ANSYS Coupled-Field Analysis Guide. ANSYS Release 10.0. 002184. © SAS IP, Inc.
Section 7.13: Sample Piezoelectric Analysis (Batch or Command Method)

local,12,,180 ! Coord. system for upper layer: polar axis -Y
csys,11 ! Activate coord. system 11
rect,0,L,-H,0 ! Create area for lower layer
rect,0,L,0,H ! Create area for upper layer
aglue,all ! Glue layers
esize,H ! Specify the element length
! et,1,PLANE223,1001,,0 ! 2-D piezoelectric element, plane stress

! ---------------------------------------------------------- !
!                         Elastic compliance matrix           !
!  !                     !                                     !
! tb,ANEL,1,,1           !                                     !
! tbda,1,1/E1,-NU12/E1,-NU12/E1 !  !                                     !
! tbda,7,1/E1,-NU12/E1 !  !                                     !
! tbda,12,1/E1 !  !                                     !
! tbda,16,1/G12 !  !                                     !

! ---------------------------------------------------------- !
!                          Piezoelectric strain matrix           !
!  !                     !                                     !
! tb,PIEZ,1,,1           !                                     !
! tbda,2,d31 !  !                                     !
! tbda,5,d33 !  !                                     !
! tbda,8,d32 !  !                                     !

! ---------------------------------------------------------- !
!                          Permittivity at constant stress      !
!  !                     !                                     !
! tb,DPER,1,,1           !                                     !
! tbdata,1,ept33,ept33 !  !                                     !

! ---------------------------------------------------------- !
! List input and converted material matrices                !

! ---------------------------------------------------------- !
! Alternative element type and material input               !
!  !                     !                                     !
! et,1,PLANEl13,7,,2 !  !                                     !
! !mp,EX,1,E1 !  !                                     !
! !mp,NUXY,1,NU12 !  !                                     !
! !mp,GXY,1,G12 !  !                                     !

! ---------------------------------------------------------- !
! Piezoelectric stress matrix                               !
!  !                     !                                     !
! tb,PIEZ,1 !  !                                     !
! !tbda,2,0.2876e-1 !  !                                     !
! !tbda,5,-0.5186e-1 !  !                                     !
! !tbda,8,-0.7014e-3 !  !                                     !

! ---------------------------------------------------------- !
! Permittivity at constant strain                           !
!  !                     !                                     !
! mp,PERX,1,11.75 !  !                                     !

type,1 $ esys,11! Generate mesh within the lower layer
amesh,1! Generate mesh within the upper layer

nsel,s,loc,x,L ! Get master node at beam tip
*get,ntip,node,0,num,min
nelec = 10
*dim,ntop,array,nelec
11 = 0
12 = L/nelec
*do,i,1,nelec
nsel,s,loc,y,H
nsel,r,loc,x,11,12
cp,i,volt,all
*get,ntop(i),node,0,num,min
11 = 12 + H/10
12 = 12 + L/nelec
*endo
nsel,s,loc,y,-H

d,all,volt,0
nsel,s,loc,x,0
d,all,ux,0,,,uy
nsel,all
fini
/SOLU
antype,static
*do,i,1,nelec
d,ntop(i),volt,V
*endo

! Actuator simulation
! Static analysis
! Apply voltages to top electrodes
solve
Uy_an = -3*d31*V*L**2/(8*H**2)  ! Theoretical solution
/com,
/com, Actuator mode results:
/com, - Calculated tip displacement Uy = %uy(ntip)% (m)
/com, - Theoretical solution        Uy = %Uy_an% (m)
fini
/SOLU                               ! Sensor simulation
antype,static,new
*do,i,1,nelec
  dele,ntop(i),volt                ! Delete applied voltages
  enddo
  d,ntip,uy,Uy                     ! Apply displacement to beam tip
  nlgeom,on                       ! Activate large deflections
  nsubs,2                         ! Set number of substeps
  cnvtol,F,1.e-3,1.e-3             ! Set convergence for force
  cnvtol,CHRG,1.e-8,1.e-3          ! Set convergence for charge
  cnvtol,AMPS,1.e-8,1.e-3          ! Use AMPS label with PLANE13
solve
fini
/POST1                             ! Sensor mode results:
*do,i,1,nelec
  Electrode %i%  Voltage = %volt(ntop(i))% (Volt)
  enddo
/com,
/com, Sensor mode results:
*do,i,1,nelec
/com, - Electrode %i%  Voltage = %volt(ntop(i))% (Volt)
  enddo
/com,
/view,,1,1,1                      ! Set viewing directions
/dscale,1,1                       ! Set scaling options
  pdisp,1                         ! Display deflected and undeflected shapes
  path,position,2,100            ! Define path name and parameters
  ppath,1,0,H                    ! Define path along bimorph length
  ppath,2,L,H                    ! Define path along bimorph length
  pdef,Volt,volt,,noav          ! Interpolate voltage onto the path
  pdef,Uy,u,y                    ! Interpolate displacement onto the path
  /axlab,x, Position (m)
  /axlab,y, Electrode Voltage (Volt)
  plpath,Volt                    ! Display electrode voltage along the path
  /axlab,x, Beam Deflection (m)
  plpath,Uy                      ! Display beam deflection along the path
  pasave                         ! Save path in a file
fini

7.14. Sample Piezoresistive Analysis (Batch or Command Method)


7.14.1. Problem Description

The sensing element consists of a rectangular p-type piezoresistor diffused on an n-type silicon diaphragm. The length of the diaphragm is oriented along the crystallographic direction X || [1 1 0] of silicon. The piezoresistor is a rectangular plate of length L and width W with two current contacts located at the ends of the plate. For maximum stress sensitivity, the piezoresistor is oriented at a 45° angle to the sides of the diaphragm. A supply voltage V_s is applied to the electrodes to produce a current in the length direction of the plate. The stress in the resistor material caused by pressure p on the diaphragm generates a proportional transverse electric field in the width direction. The output voltage V_o induced by this field is extracted from the two signal-conducting arms of length a and width b.
Figure 7.17 Four-Terminal Sensor

Perform a 2-D static piezoresistive analysis to determine the output voltage $V_o$ of the sensing element.

7.14.2. Problem Specification

Material properties and geometric parameters for the analysis are given in the $\mu$MKSV system of units.

The material properties for silicon (Si) are:

Si stiffness coefficients, MN/m$^2$:
- $c_{11} = 165.7e3$
- $c_{12} = 63.9e3$
- $c_{44} = 79.6e3$

p-type Si resistivity = 7.8e-8 T $\Omega\mu$m
p-type Si piezoresistive coefficients, (MPa)$^{-1}$:
- $\pi_{11} = 6.5e-5$
- $\pi_{12} = -1.1e-5$
- $\pi_{44} = 138.1e-5$

The geometric parameters are:

Width of piezoresistor ($W$) = 57 $\mu$m
Length of piezoresistor ($L$) = 1.5$W$
Width of signal-conducting arm ($b$) = 23 $\mu$m
Length of signal-conducting arm ($a$) = 2$b$
Size of the square diaphragm ($S$) = 2$L$

Loading for this model is:

Supply voltage ($V_s$) = 5 V
Pressure on the diaphragm ($p$) that creates stress in the X direction ($S_x$) = -10 MPa
7.14.3. Results

A series of 2-D piezoresistive static analyses was performed to determine the output voltage $V_o$ of the sensing element as a function of its geometrical dimensions. Results are compared to the analytical solution given by:

$$V_o = \frac{W}{L} V_s \left( \frac{1}{2} \pi_{44} S_x \right)$$

which gives a good approximation of the transverse voltage for ideal geometries (i.e., when $L$ is much larger than $W$, and the configuration has no signal-conducting arms and output contacts).

Table 7.17 Sensing Element Output Voltage

<table>
<thead>
<tr>
<th>L/W</th>
<th>$V_o$, mV (ANSYS Results)</th>
<th>$V_o$, mV (Analytical Results)</th>
</tr>
</thead>
<tbody>
<tr>
<td>1.25</td>
<td>25.9</td>
<td>27.6</td>
</tr>
<tr>
<td>1.5</td>
<td>23.1</td>
<td>23.0</td>
</tr>
<tr>
<td>2.0</td>
<td>18.4</td>
<td>17.3</td>
</tr>
<tr>
<td>2.5</td>
<td>15.5</td>
<td>13.8</td>
</tr>
<tr>
<td>3.0</td>
<td>12.8</td>
<td>11.5</td>
</tr>
</tbody>
</table>

7.14.4. Command Listing

```
/batch,list
/title, Four-terminal piezoresistive element, uMKSV system of units
/com,
/com, Geometric parameters:
/com,
W=57                         ! width of piezoresistor, um
L=1.5*W                      ! length of piezoresistor, um
b=23                         ! width of signal-conducting arm, um
a=2*b                        ! length of signal-conducting arm, um
```
S=2*L                         ! size of square diaphragm, um
/com,
/com, Material properties (Si):
/com,
/com, Stiffness, MN/m^2
/com, [c11 c12 c12  0 ]
/com, [c12 c11 c12  0 ]
/com, [c12 c12 c11  0 ]
/com, [ 0  0  0  c44]
/com,
c11= 16.57e4
c12= 6.39e4
c44= 7.96e4
/com,
/com, Resistivity (p-type Si), TOhm*um
rho= 7.8e-8
/com,
/com, Piezoresistive coefficients (p-type Si), (MPa)^(-1)
/com, [p11 p12 p12  0 ]
/com, [p12 p11 p12  0 ]
/com, [p12 p12 p11  0 ]
/com, [ 0  0  0  p44]
/com,
p11=6.5e-5
p12=--1.1e-5
p44=138.1e-5
/com,
/com, Pressure load, MPa
p=10
/com, Source voltage, Volt
Vs=5
/com
/prep7
et,1,PLANE223,101            ! piezoresistive element type, plane stress
et,2,PLANE183                ! structural element type, plane stress

! Specify material orientation
local,11
local,12,,,,,45              ! X-axis along [110] direction

! Specify material properties:

th,ANEL,1,,,0                ! anisotropic elasticity matrix
thda,1,c11,c12,c12
thda,7,c11,c12
thda,12,c11
thda,16,c44

mp,RSVX,1,rho                ! resistivity

th,PZRS,1                    ! piezoresistive stress matrix
thdata,1,p11,p12,p12
thdata,7,p12,p11,p12
thdata,13,p12,p12,p11
thdata,22,p44

csys,12                       ! Define piezoresistor area:
k,1,b/2,W/2+a
k,2,b/2,W/2
k,3,L/2,W/2
k,4,L/2,-W/2
k,5,b/2,-W/2
k,6,b/2,-W/2-a
k,7,-b/2,-W/2-a
k,8,-b/2,-W/2
k,9,-L/2,-W/2
k,10,-L/2,W/2
k,11,-b/2,W/2
k,12,-b/2,W/2+a
a,1,2,3,4,5,6,7,8,9,10,11,12

csys,11                       ! Define structural area:
rect, -S/2, S/2, -S/2, S/2

! Mesh areas:
aovlap, all
esys, 12
type, 1
esize, b/4
mshape, 1, 2-D
amesh, 1
type, 2
esize, b/2
amesh, 3
csys, 12
amesh, 1

! Apply electrical BC
csys, 12
nsel, s, loc, x, -L/2
nsel, r, loc, y, -W/2, W/2
cp, 1, volt, all
*get, nl, node, 0, num, min
d, nl, volt, Vs
nsel, s, loc, x, L/2
nsel, r, loc, y, -W/2, W/2
d, all, volt, 0

! left electrode:
csys, 12
nsel, s, loc, y, -W/2, W/2+a
cp, 2, volt, all
*get, nt, node, 0, num, min
d, nt, volt, Vs
nsel, s, loc, x, -b/2, b/2
nsel, r, loc, x, -b/2, b/2
cp, 3, volt, all
*get, nb, node, 0, num, min
csys, 11
nsel, all

! ground right electrode
nsel, s, loc, y, W/2, a
nsel, r, loc, x, -b/2, b/2

csys, 11
nsel, s, loc, x, -S/2
d, all, ux, 0
nsel, r, loc, y, -S/2
d, all, uy, 0
nsel, s, loc, x, S/2
sf, all, pres, p

! pressure load
nsel, all

/pbc, u, 1
/pbc, volt, 1
/pbc, cp, 1
/pnum, type, 1
/number, 1
eplot
fini

/solu
antype, static
cnvtol, amps, 1, 1.e-3
solve
fini

/post1
/com,
/com, Results:
/com, Vout (ANSYS) = %abs(volt(nt)-volt(nb))*1.e3%, mV
/com, Vout (Analytical) = %Vs*W/L*p44*p/2*1e3%, mV
fini

7.15. Sample Electromechanical Analysis (Batch or Command Method)

In this example, you will perform a direct coupled-field analysis of a MEMS structure.
Figure 7.19 Electrostatic Parallel Plate Drive Connected to a Silicon Beam

<table>
<thead>
<tr>
<th>Beam Properties</th>
<th>Parallel Plate Drive Properties</th>
</tr>
</thead>
<tbody>
<tr>
<td>( L = 150 \ \mu m )</td>
<td>( A_p = 100 (\mu m)^2 )</td>
</tr>
<tr>
<td>( b = 4 \ \mu m )</td>
<td>( \text{gap} = 1 \ \mu m )</td>
</tr>
<tr>
<td>( h = 2 \ \mu m )</td>
<td>( \varepsilon_r = 8.854\times10^{-6} \ \text{pF/\mu m} )</td>
</tr>
<tr>
<td>( E = 1.69\times10^5 \ \mu N/(\mu m)^2 )</td>
<td></td>
</tr>
<tr>
<td>( \rho = 2.332\times10^{-15} \ \text{kg/(\mu m)^3} )</td>
<td></td>
</tr>
</tbody>
</table>

7.15.1. Problem Description

A MEMS structure consists of an electrostatic parallel-plate drive connected to a silicon beam structure. The beam is pinned at both ends. The parallel-plate drive has a stationary component, and a moving component attached to the beam. Perform the following simulations:

1. Apply 150 Volts to the comb drive and compute the displacement of the beam
2. For a DC voltage of 150 Volts, compute the first three eigenfrequencies of the beam.
3. For a DC bias voltage of 150 Volts, and a vertical force of 0.1 \( \mu N \) applied at the midspan of the beam, compute the beam displacement over a frequency range of 300 kHz to 400 kHz.

The parallel plate capacitance is given by the function \( C_0/x \) where \( C_0 \) is equal to the free-space permittivity multiplied by the parallel plate area. The initial plate separation is 1 \( \mu m \). The Modal and Harmonic analysis must consider the effects of the DC voltage "preload". The problem is set up to perform a Prestress Modal and a Prestress Harmonic analysis utilizing the Static analysis results. A consistent set of units are used (\( \mu MKSV \)). Since the voltage across TRANS126 is completely specified, the symmetric matrix option (KEYOPT(4) = 1) is set to allow for use of symmetric solvers.

7.15.2. Expected Results

The expected analytic results for this example problem are as follows.

7.15.2.1. Static Analysis

\[ UY \text{ (node 2)} = -0.11076\times10^{-2} \ \mu m \]

7.15.2.2. Modal Analysis

\[ f_1 = 351 \ \text{kHz} \]
\[ f_2 = 1380 \ \text{kHz} \]
\[ f_3 = 3095 \ \text{kHz} \]
7.15.2.3. Harmonic Analysis

Frequency @ maximum displacement = 351.6 kHz
Maximum displacement = 22 µm (undamped)

7.15.2.4. Displays

Figure 7.20: “Elements of MEMS Example Problem” shows the transducer and beam finite elements.
Figure 7.21: “Lowest Eigenvalue Mode Shape for MEMS Example Problem” shows the mode shape at the lowest eigenvalue.
Figure 7.22: “Mid Span Beam Deflection for MEMS Example Problem” shows the harmonic response of the midspan beam deflection.

Figure 7.20  Elements of MEMS Example Problem

Figure 7.21  Lowest Eigenvalue Mode Shape for MEMS Example Problem
7.15.3. Building and Solving the Model

The command text below demonstrates the problem input. All text prefaced with an exclamation point (!) is a comment.

```plaintext
/batch,list
/show,file
/prep7
/title, Static, Modal, Harmonic response of a MEMS structure

L=150                     ! beam length (micrometers)
b=4                       ! beam width
h=2                       ! beam height
I=b*h**3/12               ! beam moment of inertia
E=169e3                   ! modulus (micro Newtons/micron**2)
dens=2332e-18             ! density (kg/micron**3)
per0=8.854e-6             ! free-space permittivity (pF/micron)
plateA=100                ! capacitor plate area (micron**2)
vlt=150                   ! Applied capacitor plate voltage
gapi=1                    ! initial gap (microns)

et,1,3                    ! 2-D beam element
r,1,b*h,I,h
mp,ex,1,E
mp,dens,1,dens

et,2,126,,,,1             ! Transducer element, UX-VOLT dof, symmetric
c0=per0*plateA            ! C0/x constant for Capacitance equation
r,2,0,0,gapi              ! Initial gap distance
rmore,c0                  ! Real constant C0

n,1,-10
n,2,0
n,22,1
fill
type,2
real,2
e,1,2
  ! Transducer element (arbitrary length)
type,1
real,1
e,2,3
  ! Beam elements
*repeat,20,1,1

nsel,s,loc,x,-10
```

Figure 7.22  Mid Span Beam Deflection for MEMS Example Problem
7.16. Sample Electromechanical Transient Analysis (Batch or Command Method)

The following problem illustrates a MEMS mechanical large signal transient analysis of an electromechanical transducer capacitor.
7.16.1. Results

To find the displacement $U_x$ of the transducer nodes produced by the movement of a huge mass, we use the equation:

$$U_x = X_0 + (V)(T)$$

$X_0$ is the initial gap, $V$ is the velocity of the huge mass, and $T$ is the analysis time.

**Table 7.18 Initial Values and Expected Results**

<table>
<thead>
<tr>
<th>Parameter</th>
<th>$X_0$</th>
<th>$V$</th>
<th>$T$</th>
<th>$U_x$</th>
</tr>
</thead>
<tbody>
<tr>
<td>Value</td>
<td>4.0</td>
<td>0.5</td>
<td>2.0</td>
<td>5.0</td>
</tr>
</tbody>
</table>

7.16.2. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment.

```plaintext
/batch,list
/title, huge mass, transient, velocity, sparse, unweighted
/com,----------------------------------------------------------------------
/com The MEMS mechanical large signal dynamic analysis.
/com The large signal transient of a electromechanical transducer capacitor.
/com To obtain accurate solution, avsmooth is turned off.
/com
/com Target solution
/com
/com $U_x = x_0 + v \cdot t$
/com $x_0$ : initial gap
/com $v$ : velocity of huge mass
/com $t$ : analysis time
/com
/com For $x_0=4$, $v=0.5$ and $t=2$ we have: $U_x = 4 + 0.5 \cdot 2 = 5.0$
/com,-----------------------------------------------------------------------
/nopr
eps0=8.854e-6
u=10 ! voltage difference
v=0.5 ! velocity
x0=4 ! initial gap
dt=2 ! time increment
!
/prep7
n,1,0,0
n,2,0,1
n,3,1,1
n,4,1,0
et,1,109 ! unweighted transducer element
emunit, epzro, eps0
mp, perx, 1, 1
type, 1
e,1,3,2
e,1,4,3
et,2,21,,,2 ! huge mass
r,2,0.5e+20
type, 2
real, 2
e,3
e,4
```

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7.17. Sample Electromechanical Hysteresis Analysis (Batch or Command Method)

The following problem illustrates an electromechanical hysteresis analysis. Both pull-in and release behaviors are modeled (hysteresis loop).

7.17.1. Problem Specifications

A beam is clamped at either end, suspended 0.7 µm over a ground plane with a contact stop at 0.1 µm above the ground plane.

7.17.2. Results

Beam dimensions and material properties are as follows: length is bl, width is wb, height is bh, elastic modulus is E, coefficient of friction is µ, initial gap is gap, finishing gap is gfi, pull-in voltage is V. Maximum displacement is 0.6 µm (gap-gfi).

Table 7.19 Initial Values

<table>
<thead>
<tr>
<th>bl</th>
<th>wb</th>
<th>bh</th>
<th>E</th>
<th>µ</th>
<th>gap</th>
<th>gfi</th>
<th>V</th>
</tr>
</thead>
<tbody>
<tr>
<td>80 µm</td>
<td>10 µm</td>
<td>0.5 µm</td>
<td>169 GPa</td>
<td>0.25</td>
<td>0.7 µm</td>
<td>0.1 µm</td>
<td>18 V</td>
</tr>
</tbody>
</table>

The expected results for the displacement at a given voltage are:
### Table 7.20 Expected Results

<table>
<thead>
<tr>
<th>Voltage</th>
<th>Displacement</th>
</tr>
</thead>
<tbody>
<tr>
<td>11.00</td>
<td>-0.0722</td>
</tr>
<tr>
<td>14.50</td>
<td>-0.1451</td>
</tr>
<tr>
<td>18.00</td>
<td>-0.6004</td>
</tr>
<tr>
<td>14.50</td>
<td>-0.6002</td>
</tr>
<tr>
<td>11.00</td>
<td>-0.0723</td>
</tr>
</tbody>
</table>

#### 7.17.3. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment.

```plaintext
/batch,list
/title, Gilbert, static, hysteresis, weighted, sparse
/com, ---------------------------------------------------------------
/com, 2-D Beam under electrostatic load
/com, Compare with 3-D model from the paper:
/com, J.R.Gilbert, G.K.Ananthasuresh, S.D.Senturia, (MIT)
/com, "3-D Modelling of Contact Problems and Hysteresis in
/com,
/com, 3-D Model:
/com, Beam is clamped at either end, suspended 0.7 µm over
/com, a ground plane with contact stop at 0.1 µm above the
/com, ground plane. Beam dimensions and material properties:
/com, length bl=80µm, width wb=10µm, height bh=.5µm, E=169GPa, µ=0.25
/com, Initial Gap: gap=0.7µm, finishing gap gfi=0.1um
/com, Maximum displacement is 0.6µm (gap-gfi)
/com,
/com, Value of the pull-in voltage: 18V
/com, Both pull-in and release behaviors are modeled (hysteresis loop).

!-------------- Control parameters ----------------------
vltg1 = 11.0   ! Bias voltage 1
vltg2 = 14.5   ! Bias voltage 2
vltg  = 18.0    ! Pull-in voltage
esize=0.5     ! element mesh size

!-------------- Geometry parameters ---------------------
bl=40         ! beam length
bh=.5         ! beam height
gap=.7        ! maximum gap
gap0=.6       ! air gap
eps0=8.854e-6 !

!---------------------- Model ----------------------
/prep7
emunit, epzro, eps0
et,1,42,,2
et,2,109,1, ! weighted transducer
et,3,12,,1
mp,ex,1,169e3
mp,nuxy,1,0.25
mp,perx,2,1
mp,mu,3,0
```

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r,1,c0,eps0
r,2,,1690
rect,,bl,gap,gap+bh
rect,,bl,,gap+bh
aovlap,all
nummrg,kp
ASEL,S,loc,y,gap+bh/2
AATT,1,,1
ASEL,INVERT
aatt,2,1,2
cm,area1,area
alls
esize,esize
asel,s,mat,,1
mshape,0,2
mshkey,2
amesh,all
asel,s,mat,,2
mshape,1,2
mshkey,1
amesh,all
type,3    ! gap element mesh
mat,3
real,2
*get,nomax,node,0,num,max
kn=bl/esize
k8=nomax+1
xl=0
*do,i8,1,kn+1
n52=k8
n53=n52+1
n,n52,xl,gap
n,n53,xl,gap-gap0
e,n53,n52
k8=k8+2
xl=xl+esize
*enddo
nummrg,node
alls

!--------------- Boundary Conditions -----------------
esel,s,type,,2
nsle,s
nsel,r,loc,y,gap
cm,bnode,node
nsle,s
nsel,r,loc,y,0
d,all,volt,0   ! ground
alls
nsel,s,loc,x,0     ! fix left end
d,all,ux,0
d,all,uy,0
alls
nsel,s,loc,x,bl    ! symmetry line
d,all,ux,0
esel,s,type,,3
nsle,s
nsel,r,loc,y,gap-gap0    ! fix gap elements
d,all,all
allsel, all
fini
save

/solu

!------------------ Loading (below pull-in) ---------------------
/solu

eqslv, sparse
cnvto1, f, 1, 1.0e-4
AUTOTS, ON
NSUBST, 1
outres, all, all
neqit, 50
nlgeom, on
cmsel, s, bnode   ! Bias 1
d, all, volt, vltg1
alls
solve
cmsel, s, bnode   ! Bias 2
d, all, volt, vltg2
alls
solve
fini

!---------------------------- Postprocessing -------------------
/post26
alls
NSEL, S,, 2
NSOL, 2, 2, U, Y, uy   ! Displacement at the tip
NSOL, 3, 2, VOLT,, volt  ! Voltage at the tip
PRVAR, volt, uy, , , , ,
alls
fini

!---------------------------- Pull-in ----------------------------
!--- 2-Step Solution: - moving beam to close-to-pull-in position
!--- - applying pull-in voltage and releasing BC
!-------------------------------------------------------------

!-------- Step 1 (displacement) ----------------

/solu
antype
icdele
ic, all, all, 0.0
cmsel, s, bnode
ddele, all, volt
allsel, all

nsel, s, loc, x, bl   ! Displacement BC
nsel, r, loc, y, gap
d, all, uy, -0.65
allsel, all

NSUBST, 2
solve
fini
save

/post1
set, list
alls
*get, nnodes, node, num, max
*dim, icux, nnodes
*dim, icuy, nnodes

set, last
*do, i, 1, nnodes
icux(i) = ux(i)
icuy(i) = uy(i)
*endo
dd

!--------- Step 2 (voltage) ----------
solu

alls
ddele, all ! delete old BC

esel, s, type, 2
nsel, s
nsel, r, loc, y, 0
d, all, volt, 0

alls
nsel, s, loc, x, 0 ! fix one end
nsel, a, loc, y, 0 ! fix bottom
d, all, ux, 0
d, all, uy, 0

alls
nsel, s, loc, x, bl ! symmetry line
d, all, ux, 0

esel, s, type, 3
nsel, s
nsel, r, loc, y, gap-gap0 ! fix gap elements
d, all, all

allsel, all
cmsel, s, bnode ! Apply pull-in voltage
ic, all, volt, vltg
d, all, volt, vltg
alls

*do, i, 1, nnodes ! new initial conditions
icuqx = icux(i)
icugy = icuy(i)
ic, i, ux, icuqx
ic, i, uy, icugy
*endo

outres, all, all
AUTOTS, ON
nsubst, 1
solve

!---------------- UNLOADING (from 18V to 11V) ------------
cmsel, s, bnode
d, all, volt, vltg2 ! Apply 14.5V
allsel, all
solve
cmsel, s, bnode
d, all, volt, vltg1 ! Apply 11.0V
allsel, all
solve
fini

!---------------------------- Postprocessing ----------------------
7.18. Sample Electromechanical Comb Finger Analysis (Batch or Command Method)

The following example illustrates a comb drive electrostatic problem. One finger is modeled.

7.18.1. Problem Specifications

The air gap between a comb-drive rotor and a stator is meshed with TRANS109 elements. The electrodes are modeled as the coupled equipotential sets of nodes. The stator is fixed. The rotor is attached to the spring and allowed to move (Ux). Ground nodes are allowed to move horizontally. Equilibrium between the spring force and the electrostatic force is reached at: \(ux = 0.1 \mu m\).

7.18.2. Results

The target electrostatic force \(F_e\) can be calculated using:

\[ F_e = (N)(h)(\varepsilon_0)(V)^2/g \]

where \(N\) is the number of fingers, \(h\) is the thickness in Z, \(\varepsilon_0\) is the free space permittivity, \(V\) is the driving voltage, and \(g\) is the initial lateral gap.

Table 7.21 Initial Values

<table>
<thead>
<tr>
<th>Parameter</th>
<th>N</th>
<th>h</th>
<th>(\varepsilon_0)</th>
<th>V</th>
<th>g</th>
</tr>
</thead>
<tbody>
<tr>
<td>Value</td>
<td>1.0</td>
<td>10</td>
<td>8.854e-6</td>
<td>4.0</td>
<td>5.0</td>
</tr>
</tbody>
</table>

The potential distribution of the deformed comb drive is shown in Figure 7.23: “Potential Distribution on Deformed Comb Drive”.

/*post26
alls
NSEL,S,,2
NSOL,2,2,U,Y,uy ! Displacement at the tip
NSOL,3,2,VOLT,,volt ! Voltage at the tip
/out
PRVAR,volt,uy, , , , ,
/com  **************************************************************************
/com   Expected results:
/com
/com   Voltage Displacement
/com  11.000    -0.0722
/com  14.500    -0.1451
/com  18.000    -0.6004
/com  14.500    -0.6002
/com  11.000    -0.0723
/com  **************************************************************************
alls
fini
7.18.3. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment.

```
/batch,list
/title, comb-finger, static, spring, unweighted, iccg, gnd moves
/com Combdrive electrostatic problem. One finger is modeled.
/com Air gap between comb-drive rotor and stator is meshed with TRANS109 elements.
/com The electrodes are modeled as the coupled equipotential sets of nodes.
/com Stator is fixed. Rotor is attached to the spring and allowed to move (Ux).
/com Ground nodes are allowed to move horizontally.
/com Equilibrium between spring force and electrostatic force is reached at:
/com
/com ux = 0.1 microns
/com
/com REFERENCE SOLUTION:
/com
/com W.C.Tang et al, "Electrostatic combdrive of lateral polysilicon resonators",
/com Sensors and Actuators A, 21-23 (1990), 328-331
/com
/com Target electrostatic force:  Fe = N*h*Eps0*V^2/g
/com (N-number of fingers, h-thickness in z, Eps0 - free space permittivity,
/com V - driving voltage and g - initial lateral gap)
/com
/nopr !----------------- Combdrive Parameters -----------------
```
eps0=8.854e-6  ! free space permittivity

g0=5.0        ! Initial gap

h=10          ! Fingers width (in-plane)

L=100         ! Finger length

x0=0.5*L      ! Fingers overlap

ftol=1.0e-5

esize=1.0     ! Element size

k=2.8333e-4   ! spring stiffness

vlgt=4.0      ! Applied voltage

!---------------------- Combdrive Finger Geometry ----------------------

/prep7

et,1,109,,       ! unweighted transducer

demunit,epzro,eps0

mp,perx,1,1

r,1,1.0

et,2,14,,1       ! linear spring, UX DOF

r,2,k            ! spring parameters (k/2)

et,3,42          ! PLANE42 for moving finger

mp,ex,2,169e3

mp,nuxy,2,0.25

r,3,

BLC4,0,-h/2,L,h  ! create all areas

BLC4,-h,-h/2,h,h

BLC4,-h,-h-g0,h,h/2+g0

BLC4,-h,h/2,h,h/2+g0

BLC4,L-x0,h/2+g0,L,h/2

BLC4,L-x0,-h-g0,L,h/2

BLC4,0,-h-g0,2*L-x0,2*(h+g0)

aovlap,all

nummrg,kp

! ------------------------ Areas Attributes ------------------------

asel,s,area,,1  ! moving finger

asel,a,area,,8

asel,a,area,,9

asel,a,area,,10

aatt,2,3,3      ! material 2, real 3, type 3

asel,s,area,,11 ! air gap

aatt,1,1,1      ! material 1, real 1, type 1

alls

!--------------------- Air Gap Free meshing ---------------------

asel,s,area,,11

esize,esize

mshape,1,2

mshkey,0

amesh,all

alls

!------------------------ Meshing of Moving finger -----------------

asel,s,area,,1

asel,a,area,,8

asel,a,area,,9

asel,a,area,,10

esize,esize

mshape,0,2

mshkey,1

amesh,all

alls

!----------------------- Spring Element -----------------------
Chapter 7: Direct Coupled-Field Analysis

```plaintext
type, 2
real, 2

*get, node_num, node,, count
n, node_num+1, 0.0, 0.0, 0.0
nsel, s, loc, x, -h
nsel, r, loc, y, 0.0
*get, node0, node,, num, max
e, node0, node_num+1
alls

! -------------- Nodal components for BC --------------

LSEL, s, line,, 15
LSEL, a, line,, 33
LSEL, a, line,, 3
LSEL, a, line,, 2
LSEL, a, line,, 1
LSEL, a, line,, 31
LSEL, a, line,, 9

NSLL, S, 1
cm, rotor, node ! component 'rotor'
alls

LSEL, s, line,, 20
LSEL, a, line,, 17
LSEL, a, line,, 37
LSEL, a, line,, 23
LSEL, a, line,, 24

NSLL, S, 1
cm, ground, node ! component 'ground'
alls

fini

!------------ Boundary conditions -------------
/solu
nsel, s, loc, y, -(h+g0) ! symmetry (uy=0)
nsel, a, loc, y, h+g0
d, all, uy, 0
alls
d, node_num+1, ux, 0.0 ! fix the spring (ux=0)

cmsel, s, ground ! ground (ux=uy=volt=0)
d, all, volt, 0.0
d, all, uy, 0.0
alls
LSEL, s, line,, 20 ! fix horizontal (ux=0)
LSEL, a, line,, 37
LSEL, a, line,, 24
NSLL, S, 1
d, all, ux, 0.0

cmsel, s, rotor ! apply voltage to rotor
d, all, volt, vltg
alls
fini

!------------- Solution --------------------------

/solu
eqslv, iccg
SOLNCTRL, ON
cnvtol, f, 1, ftol
```

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7.19. Sample Force Calculation of Two Opposite Electrodes (Batch or Command Method)

The goal of the simulation is to determine the nature of the horizontal (dragging) electrostatic force produced by two infinitely narrow, semi-infinite electrodes.

7.19.1. Problem Specifications

The potential drop between the electrodes is \( U = 4V \). Potentials \( U/2 \) and \(-U/2\) are applied to the set of nodes representing top and bottom line electrodes. There are no active structural degrees of freedom in the finite element model.

7.19.2. Results

Because of the thin geometry of electrodes, the fringing effects are significant. The potential distribution is shown in Figure 7.24: “Potential Distribution of Overlapping Electrodes”.

```plaintext
nlgeom, on
outres, all, all
NSUBST, 20, 100, 20
solve
fini

!---------------- Postprocessing ---------------------
/post1
/out
/set, last
*get, ux_1, node, node0, u, x

CMSEL, s, ground
/com -----------------------------------------------------
/com Components of electrostatic force on stator:
/com -----------------------------------------------------
/fsum,,
/com
/com Displacement of the combdrive (Ux):
*/vwrite, ux_1
('' Combdrive displacement = ', e13.6)
ux_ref = 0.1
*/vwrite, ux_ref
('' Reference displacement = ', e13.6)
fini
```
7.19.3. Command Listing

The command listing below demonstrates the problem input. Text prefaced by an exclamation point (!) is a comment.

```
/batch,list
/title,Force Calculation of Two Opposite Electrodes
/com
/com ---------------- Problem Description ----------------
/com The goal of the simulation is to determine the nature of
/com horizontal (dragging) electrostatic force produced by
/com two infinitely narrow semi-infinite electrodes
/com Potential drop between electrodes U = 4V.
/com Potentials U/2 and -U/2 are applied to the
/com set of nodes representing top and bottom line electrodes.
/com There are no active structural degrees of freedom
/com in the finite element model.
/com
/com -----------------------------------------------
/nopr
H=80     ! infinity size
x0=H/5    ! overlap
g0=H/40   ! Initial gap
vltg=4.0  ! potential drop
eps0=8.854e-6
umax = 0.0
```
Section 7.19: Sample Force Calculation of Two Opposite Electrodes (Batch or Command Method)

ftol=1.0e-1
esize=H/80

/prep7
et,1,109,1,             ! weighted transducer
eunix,epsro,eps0
ve1=g0
ve2=(H-ve1)/2
dx=(H-x0)/2
BLC4,,dx,ve2
BLC4, dx,,x0,ve2
BLC4, dx+x0,,dx,ve2
BLC4, ve2,dx,ve1
BLC4, dx,ve2,x0,ve1
BLC4, dx+x0,ve2,dx,ve1
BLC4, ve2+ve1,dx,ve2
aglue,all
type,1
mat,1
mshape,1,2
mshkey,0
esize,esize
amesh,all
alls

!!!
!!! Setup Bottom Electrode
!!!
nssel,s,loc,y,ve2-1.0e-6,ve2+1.0e-6
nsel,r,loc,x,0,dx+x0
d,all,volt,-2.0
cm,bot,node
alls
!!!
!!! Setup Top Electrode
!!!
nssel,s,loc,y,ve1+ve2-1.0e-6,ve1+ve2+1.0e-6
nsel,r,loc,x,dx,2*dx+x0
d,all,volt,2.0
cm,top,node
alls
!!!
!!! Apply DOF
!!!
d,all,ux,0.0
d,all,uy,0.0

!--------extra components---------
nsel,s,loc,y,ve2-1.0e-6,ve2+1.0e-6
nsel,r,loc,x,dx,dx+x0
cm,bot1,node
alls
nsel,s,loc,y,ve1+ve2-1.0e-6,ve1+ve2+1.0e-6
nsel,r,loc,x,dx,dx+x0
cm,top1,node
alls
/solu
solve
/out
fini

/post1
set,last
!!!
!!! Setup Analytical Results
!!!
Atoptip=-3.542e-5
Abottip=3.542e-5
ATFx=-3.542e-5
ATFy=-2.833e-4  
ABFx=3.542e-5  
ABFy=2.833e-4  

!!! Get Ansys Results  
!!!  
*GET,TOPTIP,node,2200,RF,FX  ! Get Fx Reaction at Tip of Top Electrode  
*GET,BOTTIP,node,1503,RF,FX  ! Get Fx Reaction at Tip of Bot Electrode  
ForceTOP=TOPTIP  ! Take Inverse of Reaction Force  
ForceBOT=BOTTIP  ! Take Inverse of Reaction Force  
cmset,s,top  ! Select Top Electrode  
/com  
/com ****** TOP ELECTRODE FSUM  
FSUM  ! Print Sum of Forces  
cmset,s,bot  ! Select Bottom Electrode  
/com  
/com ****** BOTTOM ELECTRODE FSUM  
FSUM  ! Print Sum of Forces  
/com  
/com ******************************** Expected Results ********************************  
/com  
/com TOP ELECTRODE RESULTS:  
/com  
*vwrite,Atoptip,ForceTOP  
('Target FXtip Result = ', E12.4, ' Ansys Result = ', E12.4)  
/com  
*vwrite,ATFx,ATFy  
('Target FSUM Fx Result = ',E12.4,' - Target FSUM Fy Result = ',E12.4)  
/com  
/com TOP ELECTRODE RESULTS:  
/com  
*vwrite,Abottip,ForceBOT  
('Target FXtip Result = ', E12.4, ' Ansys Result = ', E12.4)  
/com  
*vwrite,ABFx,ABFy  
('Target FSUM Fx Result = ',E12.4,' - Target FSUM Fy Result = ',E12.4)  
/com  
/com  
/com **************************************************************************  
inish  

7.20. Where to Find Other Examples

Several ANSYS publications, particularly the ANSYS Verification Manual, describe additional direct coupled-field analyses.

The ANSYS Verification Manual consists of test case analyses demonstrating the analysis capabilities of the ANSYS program. While these test cases demonstrate solutions to realistic analysis problems, the ANSYS Verification Manual does not present them as step-by-step examples with lengthy data input instructions and printouts. However, most ANSYS users who have at least limited finite element experience should be able to fill in the missing details by reviewing each test case's finite element model and input data with accompanying comments.

The following list shows you some of the direct coupled-field analysis test cases that the ANSYS Verification Manual includes:

VM23 - Thermal-Structural Contact of Two Bodies  
VM119 - Centerline Temp of an Electrical Wire  
VM126 - Heat Transferred to a Flowing Fluid  
VM171 - Permanent Magnet Circuit with an Elastic Keeper  
VM175 - Natural Frequency of a Piezoelectric Transducer  
VM176 - Frequency Response of Electrical Input Admittance for a Piezoelectric Transducer  
VM177 - Natural Frequency of Submerged Ring
VM185 - AC Analysis of a Slot Embedded Conductor
VM186 - Transient Analysis of a Slot Embedded Conductor
VM190 - Ferromagnetic Inductor
VM207 - Stranded Coil Excited by External Circuit
VM215 - Thermal-Electric Hemispherical Shell with Hole
VM231 - Piezoelectric Rectangular Strip Under Pure Bending Load
VM237 - RLC Circuit with Piezoelectric Transducer
VM238 - Wheatstone Bridge Connection of Piezoresistors
Chapter 8: Coupled Physics Circuit Simulation

You can often perform coupled physics simulations using a circuit analogy. Components such as "lumped" resistors, sources, capacitors, and inductors can represent electrical devices. Equivalent inductances and resistances can represent magnetic devices, and springs, masses, and dampers can represent mechanical devices. ANSYS offers a set of tools to perform coupled simulations through circuits. A Circuit Builder is available to conveniently create circuit elements for electrical, magnetic, piezoelectric, and mechanical devices. See Section 15.3: Using the Circuit Builder in the ANSYS Low-Frequency Electromagnetic Analysis Guide for details.

A coupled physics circuit simulation can be performed entirely with lumped elements. However in many instances, due to the distributed nature of the physics component, nonlinearities, etc., a simple "reduced order" element may not be sufficient. The ANSYS Circuit capability allows the user to combine both lumped elements where appropriate, with a "distributed" finite element model in regions where characterization requires a full finite element solution. What allows the combination of lumped and distributed models is a common degree-of-freedom set between lumped elements and distributed elements.

Section 8.1: Electromagnetic-Circuit Simulation describes the coupling of electrical circuits with distributed electromagnetic finite element models to accurately model circuit-fed electromagnetic devices.

Section 8.2: Electromechanical-Circuit Simulation describes the coupling of electric circuits, an electromechanical transducer, and structural lumped elements to model micro-electromechanical devices (MEMS) driven by electrostatic-structural coupling.

Section 8.3: Piezoelectric-Circuit Simulation describes the coupling of electrical circuits with distributed piezoelectric finite element models to simulate circuit-fed piezoelectric devices.

For example problems, see Section 8.4: Sample Electromechanical-Circuit Analysis and Section 8.5: Sample Piezoelectric-Circuit Analysis (Batch or Command Method).

8.1. Electromagnetic-Circuit Simulation

You use this analysis, available in the ANSYS Multiphysics and ANSYS Emag products, to couple electromagnetic field analysis with electric circuits. You can couple electric circuits directly to current source regions of the finite element domain. The coupling is available in 2-D as well as 3-D analysis and includes stranded (wound) coils, massive (solid) conductors, and solid source conductors. Typical applications for stranded coils include circuit-fed analysis of solenoid actuators, transformers, and electric machine stators. Bus bars and squirrel-cage rotors are examples of massive conductor applications.

To do a coupled electromagnetic-circuit analysis, you need to use the general circuit element (CIRCU124) in conjunction with one of these element types:

- PLANE53 -- 2-D 8-Node Magnetic Solid
- SOLID97 -- 3-D Magnetic Solid
- SOLID117 -- 3-D 20-Node Magnetic Solid

The analysis may be static, harmonic (AC), or transient, and follows the same procedure described in the ANSYS Low-Frequency Electromagnetic Analysis Guide. The circuit coupling is linear in that conductors are assumed to have isotropic linear material properties, and the formulation is matrix-coupled. Nonlinearities may exist in the electromagnetic domain to account for material saturation.

For stranded coils and massive conductors, the following coupled circuit sources in the CIRCU124 element can link the electric circuit to the finite element (electromagnetic) domain:
Stranded coil KEYOPT(1) = 5
2-D massive conductor KEYOPT(1) = 6
3-D massive conductor KEYOPT(1) = 7

For solid source conductors, the CIRCU124 circuit elements and circuit sources can directly link to the finite element domain.

The ANSYS Circuit Builder is available to conveniently create circuit elements. See Section 15.3: Using the Circuit Builder in the ANSYS Low-Frequency Electromagnetic Analysis Guide for details.

You link the electric circuit and the electromagnetic domain through a common node (or a set of common nodes). That is, a node in the source conductor region of the electromagnetic domain is used in the definition of the circuit component element that is linked with it. For example, the K node of a CIRCU124 stranded coil element receives the same node number as a node in the PLANE53 element representing the source conductor region (see Figure 8.1: “2-D Circuit Coupled Stranded Coil”).

The source conductor elements (PLANE53 or SOLID97) must match the degree-of-freedom set associated with the circuit component to which it is linked. The DOF set for PLANE53 and SOLID97 is chosen through KEYOPT(1). (See the element descriptions in the ANSYS Elements Reference for details.)

You must specify real constants for the source conductor elements. They describe geometric properties as well as coil information for stranded coil sources. See the ANSYS Elements Reference for details about the real constants.

The next section reviews the procedure for electromagnetic-circuit coupling in detail.

### 8.1.1. 2-D Circuit Coupled Stranded Coil

This option couples an electric circuit to a stranded coil source in a 2-D planar or axisymmetric finite element model. Typically, you use it to apply a voltage or current load through an external circuit to the coil of a device. The coupling involves using one node from the PLANE53 stranded coil elements as the K node of the CIRCU124 stranded coil component, as shown in Figure 8.1: “2-D Circuit Coupled Stranded Coil”.

**Figure 8.1 2-D Circuit Coupled Stranded Coil**

The degrees of freedom CURR (current) and EMF (electromotive force drop, or potential drop) are coupled across the circuit to the electromagnetic domain. CURR represents the current flowing per turn of the coil and EMF represents the potential drop across the coil terminals. Since the coil has only one unique current and one potential drop across the coil terminals, a single value for each of these degree of freedom unknowns is required. Thus, you must couple all nodes of the coil region in the finite element domain in the CURR degree of freedom and in the EMF degree of freedom. To do so, perform these tasks:

1. Create a CIRCU124 stranded coil circuit element (KEYOPT(1) = 5).
2. Create a PLANE53 stranded coil in the finite element model with the appropriate degree of freedom option (KEYOPT(1) = 3). Define the coil real constants.

3. Assign the "K" node of the CIRCU124 stranded coil element to any node in the coil region of the finite element model.

4. Select all the nodes of the PLANE53 coil elements and couple them in the CURR degree of freedom and in the EMF degree of freedom.

**8.1.2. 2-D Circuit Coupled Massive Conductor**

This option couples an electric circuit to a massive conductor in a 2-D planar or axisymmetric finite element model. Typically you use it to apply a voltage or current load through an external circuit to a solid conductor such as a bus bar or a solid stator conductor. The coupling involves using one node from the PLANE53 massive conductor elements as the K node of the CIRCU124 massive conductor element, as shown in Figure 8.2: “2-D Circuit Coupled Massive Conductor”.

**Figure 8.2 2-D Circuit Coupled Massive Conductor**

The degrees of freedom CURR (current) and EMF (electromotive force drop, or potential drop) are coupled across the circuit to the electromagnetic domain. CURR represents the total current flowing in the massive conductor, and EMF represents the potential drop across the ends of the conductor. Since the conductor has only one unique current in and one potential drop exists across the conductor, a single value for each of these degree of freedom unknowns is required. Thus, you must couple all nodes of the conductor region in the finite element domain in the CURR degree of freedom and in the EMF degree of freedom. Follow these steps to do so:

1. Create a 2-D CIRCU124 massive conductor circuit element (KEYOPT(1) = 6).
2. Create a PLANE53 massive conductor in the finite element model with the appropriate degree of freedom option (KEYOPT(1) = 4). Define the conductor real constants.
3. Assign the "K" node of the CIRCU124 massive conductor element to any node in the massive conductor region of the finite element model.
4. Select all the nodes of the PLANE53 conductor elements and couple them in the CURR degree of freedom and in the EMF degree of freedom.

**8.1.3. 3-D Circuit Coupled Stranded Coil**

This option couples an electric circuit to a stranded coil in a 3-D finite element model. Typically, this option applies a voltage or current load through an external circuit to the coil of a device. The coupling involves using one node from the SOLID97 stranded coil elements as the K node of the CIRCU124 stranded coil element, as shown in Figure 8.3: “3-D Circuit Coupled Stranded Coil”.
The degrees of freedom CURR (current) and EMF (electromotive force drop, or potential drop) are coupled across the circuit to the electromagnetic domain. CURR represents the current flowing per turn of the coil, and EMF represents the potential drop across the coil terminals. Since there is only one unique current in the coil and one potential drop across the coil terminals, specify a single value for each of these degree of freedom unknowns. You must couple all nodes of the coil region in the finite element domain in the CURR degree of freedom and in the EMF degree of freedom. To do so, perform these steps:

1. Create a CIRCU124 stranded coil circuit element (KEYOPT(1) = 5).
2. Create a SOLID97 stranded coil in the finite element model with the appropriate degree of freedom option (KEYOPT(1) = 3). Define the coil real constants.
3. Assign the "K" node of the CIRCU124 stranded coil element to any node in the coil region of the finite element model.
4. Select all the nodes of the coil in the SOLID97 coil elements and couple them in the CURR degree of freedom and in the EMF degree of freedom.

### 8.1.4. 3-D Circuit Coupled Massive Conductor

This option couples an electric circuit to a massive conductor in a 3-D finite element analysis. You use this typically to apply a voltage or current load through an external circuit to a solid conductor such as a bus bar or a solid stator conductor. The coupling involves using two nodes from the SOLID97 massive conductor elements as the K and L nodes of the CIRCU124 massive conductor element, as shown in Figure 8.4: "3-D Circuit Coupled Massive Conductor".
Figure 8.4 3-D Circuit Coupled Massive Conductor

The degrees of freedom CURR (current) and VOLT (voltage) are coupled across the circuit to the electromagnetic domain. CURR represents the total current flowing in the massive conductor, and VOLT represents the potential in the conductor. The CURR degree of freedom is a single valued unknown and is only required to be active on the "front" and "back" faces on the massive conductor region. You must flag these front and back faces with the magnetic circuit interface (MCI) option of the SF command (Main Menu> Preprocessor> Define Loads> Apply> Flag). To indicate the proper direction of current flow (which is from node K to node L), set the MCI flag to -1 on the node K face and +1 on the node L face. This is analogous to the standard sign convention of positive current flowing from node I to node J in the circuit element. Internal to the conductor, the CURR degree of freedom is not used. The VOLT degree of freedom represents the electric potential in the massive conductor. The procedure is as follows:

1. Create a CIRCU124 massive conductor circuit element for 3-D (KEYOPT(1) = 7).
2. Create a SOLID97 massive conductor in the finite element model with the appropriate degree of freedom option (KEYOPT(1) = 4). Define the conductor real constants.
3. Assign the "K" node of the CIRCU124 massive conductor element to any node on one face of the massive conductor region of the finite element model.
4. Assign the "L" node of the CIRCU124 massive conductor element to any node on the other face of the massive conductor region of the finite element model.
5. Select the nodes of the face containing the "K" node and specify a magnetic circuit interface flag (MCI) value of -1 via the SF command.
6. Select the nodes of the face containing the "L" node and specify a magnetic circuit interface (MCI) flag value of +1 via the SF command.
7. Couple node "I" of the CIRCU124 massive conductor element and the face "K" nodes of the massive conductor elements in the VOLT degree of freedom.
8. Couple the face "L" nodes of the massive conductor elements in the VOLT degree of freedom. (This coupling assumes that the face of the conductor is straight-sided and that the current flows perpendicular to the face.)
9. Couple the nodes of both faces of the massive conductor region in the CURR degree of freedom.
If a VOLT constraint is required to a face of the finite element model (that is, to enforce a symmetry boundary condition), you must place the constraint on the circuit node (node K or L) and not directly onto the finite element face nodes. Constraining the finite element face nodes may lead to an erroneous circuit solution.

### 8.1.5. 3-D Circuit Coupled Solid Source Conductor

This option couples an electric circuit to a solid source conductor as shown in a typical configuration in Figure 8.5: “3-D Circuit Coupled Solid Source Conductor”. A solid source conductor represents a solid conductor with a DC current distribution within the conductor walls. The solid conductor of the finite element region represents an equivalent resistance to the circuit. When hooked to an external circuit, the resulting solution determines the conductor DC current distribution, which is used as a source excitation for the electromagnetic field.

**Figure 8.5 3-D Circuit Coupled Solid Source Conductor**

Circuit coupled solid source conductors can be used in static, harmonic, and transient analysis. However, the solution within the conductor itself is limited to a DC current distribution with no eddy current effects or back emf effects. The following elements offer the solid conductor source option:

- **SOLID117, KEYOPT(1) = 5 or 6** (solenoidal formulation)
- **SOLID97, KEYOPT(1) = 5 or 6** (solenoidal formulation)

The solenoidal formulation of SOLID117 and SOLID97 uses an electric scalar potential (VOLT) that is compatible with the following CIRCU124 circuit elements:

#### Components

- Resistor (KEYOPT(1) = 0)
- Inductor (KEYOPT(1) = 1)
- Capacitor (KEYOPT(1) = 2)
- Mutual Inductor (KEYOPT(1) = 8)

#### Sources

- Independent Current Source (KEYOPT(1) = 3)
- Independent Voltage Source (KEYOPT(1) = 4)
- Voltage Controlled Current Source (KEYOPT(1) = 9)
- Voltage-Controlled Voltage Source (KEYOPT(1) = 10)
Current-Controlled Voltage Source (KEYOPT(1) = 11)
Current-Controlled Current Source (KEYOPT(1) = 12)

You can also use the solenoidal formulation with the diode element (CIRCU125). Because the elements are compatible, the CIRCU elements can be directly connected to the SOLID elements via the VOLT degree of freedom.

### 8.1.6. Taking Advantage of Symmetry

Often it is convenient to take a symmetry cut of a device to construct a finite element model. Coupled electromagnetic-circuit analysis can consider two types of symmetry: conductor symmetry and circuit symmetry.

**Conductor symmetry** - This type of symmetry involves modeling only part of a conductor due to symmetric behavior of the magnetic field. For example, you can model a C-shaped magnet with a single winding symmetrically placed about the return leg in half-symmetry. The real constants defined for the finite element conductor regions automatically handle symmetry sectors by requiring you to specify the full conductor area (real constant CARE, and also VOLU for 3-D). The program determines from the conductor elements the fraction of the conductor modeled and appropriately handles the symmetry model. Also, for 2-D planar problems you can specify the length of the device (real constant LENG) which the program handles appropriately.

**Circuit symmetry** - For coupled electromagnetic-circuit simulation, you must model the entire electric circuit of the device; however, you may be able to take advantage of symmetry in the finite element domain. For example, you may only need to model one pole of a rotating electric machine to obtain a finite element solution. However, you must model completely the circuit which accounts for all the slot windings in the full machine.

You can account for symmetric sectors of coil windings or massive conductors not modeled in the finite element domain in the circuit using the appropriate circuit component option (CIRCU124 element with KEYOPT(1) = 5, 6, or 7). The "K" nodes of these circuit components should be independent nodes (not connected to the finite element mesh or to any other node in the circuit) and should be coupled through the EMF degree of freedom with the "K" node of the circuit component which is directly coupled to the finite element domain. A 2-D problem illustrated in Figure 8.6: “Circuit for Go and Return Conductors” demonstrates the connection.

**Figure 8.6 Circuit for Go and Return Conductors**

![Figure 8.6: Circuit for Go and Return Conductors](image)

Figure 8.6: “Circuit for Go and Return Conductors” illustrates two massive conductors carrying current in opposite directions, connected at their ends through a finite resistance (R) and inductance (L) (to simulate end effects), and driven by a voltage source (V₀). Conductor symmetry allows for modeling only the top half of the conductor pair. Additional symmetry about the y-axis can eliminate the need to model the "left" conductor as long as the circuit takes care of the conductor in the circuit mesh. The full circuit required to simulate the two-conductor system is shown with the voltage source, resistor, and massive conductor source components.
The I, J, and K nodes of the massive conductor components are highlighted for clarity. The right massive conductor is directly linked to the "right" conductor in the finite element domain through node K1. The left massive conductor component has no corresponding modeled conductor region in the finite element domain. However, coupling node K1 to node K2 through the EMF degree of freedom will simulate the effect of the "left" conductor which is not modeled, but which has the same EMF drop as the "right" conductor.

The stranded coil circuit components for 2-D and 3-D, as well as the 2-D massive conductor component, work on the same principle for symmetry modeling by coupling the EMF degree of freedom between the K nodes as described above. For the 3-D massive conductor the procedure differs. In this case, independent K and L nodes for the unmodeled circuit component should be coupled through the VOLT degree of freedom of the massive circuit component (nodes K and L) that is connected to a modeled finite element region.

### 8.1.7. Series Connected Conductors

Series connected windings can be modeled.

Figure 8.7: “Series Wound Stranded Conductor” illustrates a single phase voltage-fed stranded winding for a 2-D problem containing four coil slots (typical arrangement of a machine). The slots represent a single continuous winding with current direction (D "out" (+1), x "in" (-1)) specified in the real constant set of the PLANE53 element type. The dotted lines represent the common node of the stranded coil current source and the finite element current domain.

**Figure 8.7 Series Wound Stranded Conductor**

Because all the slots are connected in series, they form a single loop and will each carry the same current ("i" from CURR degree of freedom). However, each slot may have a different voltage drop (EMF). Each slot will require a unique CURR and EMF node coupled set.

A summary of the coupled node sets follows:

<table>
<thead>
<tr>
<th>Set Number</th>
<th>DOF</th>
<th>Nodes (by Slot)</th>
</tr>
</thead>
<tbody>
<tr>
<td>1</td>
<td>CURR</td>
<td>N1</td>
</tr>
<tr>
<td>2</td>
<td>CURR</td>
<td>N2</td>
</tr>
<tr>
<td>3</td>
<td>CURR</td>
<td>N3</td>
</tr>
<tr>
<td>4</td>
<td>CURR</td>
<td>N4</td>
</tr>
</tbody>
</table>
The same procedure also applies to massive conductors in series.

8.2. Electromechanical-Circuit Simulation

In many instances you can analyze micro-electromechanical devices (MEMS) using "reduced order" models. Reduced order models represent lumped-parameter equivalencies to larger, more complex systems. For example, you can reduce an electrostatic comb drive to one or more electromechanical transducer elements (TRANS126), and mechanical structures in resonators, filters, or accelerometers to equivalent springs (COMBIN14, COMBIN39), dampers (COMBIN14, COMBIN39), and masses (MASS21). By reducing systems to lumped elements, you can perform transient dynamic simulations, or time-harmonic simulations at a fraction of the cost of a full finite element analysis.

The ANSYS Circuit Builder supports several mechanical lumped elements, an electromechanical transducer element, as well as electrical circuit elements. These elements include:

**Electrical:**
- CIRCU124 -- General Circuit Element
- CIRCU125 -- Common or Zener Diode Element

**Mechanical:**
- COMBIN14 -- Spring - Damper Element
- COMBIN39 -- Nonlinear Spring Element
- MASS21 -- Structural Mass Element

**Transducer:**
- TRANS126 -- Electromechanical Transducer Element

You can use all of the above element types in the construction of a reduced order electromechanical model. The electrical options in CIRCU124 allow the construction of circuitry to feed an electromechanical drive structure simulated by the transducer element TRANS126. The transducer element stores electrical energy and converts it to mechanical energy. Mechanical elements attached to the transducer element receive the mechanical energy and respond accordingly. You can also model the reverse process. In this case, mechanical loads applied to the mechanical elements act on the transducer element, converting mechanical energy into an electrical signal which can be passed through an electrical circuit to achieve a desired signal response.

Springs and dampers are separate discrete elements in the circuit builder. While the elements COMBIN14 and COMBIN39 can simultaneously model both a spring and damper, for convenience and simplicity the circuit builder allows only a spring or damper to be created for each circuit element constructed. Icons for springs, dampers, and masses appear during the element definition. After inputting the real constants, the final icon appears. If the element is nonlinear, a "bar" appears above the icon.
You can use the circuit builder to easily define the nodes, elements, and real constants for the transducer elements (TRANS126) and the mechanical elements (COMBIN14, COMBIN39, MASS21). You use standard procedures to define loads and boundary conditions for these elements.

More information on the circuit builder can be found in Section 15.3: Using the Circuit Builder in the ANSYS Low-Frequency Electromagnetic Analysis Guide.

Several important points to remember when performing an electromechanical simulation are:

- You must align the TRANS126 element along the axis of the active structural degree of freedom. This is in general along one of the three Global Cartesian Axes. If the nodes of the element are rotated into a local coordinate system (NROTAT command), you may align the element along the local coordinate system axis. The separation distance between the I and J nodes of the TRANS126 element is immaterial; however, the positioning of the I and J nodes with respect to the axis is important. See TRANS126 in the ANSYS Elements Reference for more information about valid orientations. It may be helpful to activate the working plane grid in the circuit builder to ensure that the element is aligned properly. To do so, choose one of the following:

  Main Menu> Preprocessor> Modeling> Create> Circuit> Center WP
  Utility Menu> Working Plan> WP Settings
  Then turn on the working plane grid in the WP Settings dialog box that appears.

- Align the mechanical spring and damper elements (COMBIN14, COMBIN39) along the axis of the active structural degree of freedom. The separation distance between nodes is immaterial; however, the element will not carry any moment that may be induced by an off-axis load. These elements normally issue a warning when the I and J nodes are noncoincident; however, the circuit builder suppresses this warning with an undocumented KEYOPT option (KEYOPT(2) = 1) set for the circuit builder.

- When performing a static or transient analysis, you may have to tighten the convergence criteria to obtain the correct displacement direction for the TRANS126 element. To do so, use CNVTOL,F,1,1E-12.

  Note — You can directly attach reduced order electromechanical models to a structural finite element model. This is advantageous when a structural component cannot be conveniently reduced to a simple spring/mass/damper representation. The connection is done via common nodes and their active degrees of freedom (or separate nodes and node coupling).

See Section 8.4: Sample Electromechanical-Circuit Analysis for an example problem.

### 8.3. Piezoelectric-Circuit Simulation

You use this analysis, available in the ANSYS Multiphysics product, to determine one of the following:

- Voltage and current distribution in an electric circuit with piezoelectric devices.
- Structural and electric field distributions in a circuit-fed piezoelectric device.

To do a coupled piezoelectric-circuit analysis, you need to use the piezoelectric circuit element (CIRCU94) with one of the following piezoelectric elements:

- PLANE13, KEYOPT(1) = 7, coupled-field quadrilateral solid
- SOLID5, KEYOPT(1) = 0 or 3, coupled-field brick
- SOLID98, KEYOPT(1) = 0 or 3, coupled-field tetrahedron
- PLANE223, KEYOPT(1) = 1001, coupled-field 8-node quadrilateral
- SOLID226, KEYOPT(1) = 1001, coupled-field 20-node brick
- SOLID227, KEYOPT(1) = 1001, coupled-field 10-node tetrahedron
You can connect electrical circuits directly to the 2-D or 3-D piezoelectric finite element models. Typical applications include circuit-fed piezoelectric sensors and actuators, active and passive piezoelectric dampers for vibration control, and crystal oscillator and filter circuits for communication systems.

You can use the CIRCU94 element to model the following components: resistor, inductor, capacitor, independent current source, and independent voltage source. KEYOPT(1) defines the component type as shown in Figure 8.8: “CIRCU94 Components”. Real constants specify values for resistance, inductance, and capacitance. For independent current and voltage sources, KEYOPT(2) specifies the type of excitation. You can specify constant load (transient) or constant amplitude load (harmonic), sinusoidal, pulse, exponential, or piecewise linear loads. Real constants specify the load functions. Besides the source loads, the only other "load" is a VOLT = 0 specification (D command) at the ground nodes (other nodal loads are not recommended). For more information, see CIRCU94 in the ANSYS Elements Reference.

**Figure 8.8 CIRCU94 Components**

![Resistor](image)

KEYOPT(1) = 0
DOF = VOLT

![Inductor](image)

KEYOPT(1) = 1
DOF = VOLT

![Capacitor](image)

KEYOPT(1) = 2
DOF = VOLT

![Independent Current Source](image)

KEYOPT(1) = 3
DOF = VOLT

![Independent Voltage Source](image)

KEYOPT(1) = 4
DOF = VOLT (I,J), CURR (K)

KEYOPT(1) = 0, 1, 2, and 3 define resistor, inductor, capacitor and current source components using two nodes I and J. To define a voltage source you need to specify a third, "passive," node (K) as shown for KEYOPT(1) = 4. The program uses this node internally and it does not need to be attached to the circuit or the piezoelectric finite element model. For all circuit components, positive current flows from node I to node J.

You can create a circuit by defining nodes, elements, element types, and real constants for each electric component. However, it is more convenient to create a circuit model interactively using the ANSYS Circuit Builder. To build a circuit interactively, follow the procedure described in Section 15.3: Using the Circuit Builder in the ANSYS Low-Frequency Electromagnetic Analysis Guide. To access the piezoelectric circuit components, choose **Main Menu> Preprocessor> Modeling> Create> Circuit> Builder> Piezoelectric**.
When building an electric circuit, you should avoid inconsistent configurations as illustrated in Section 15.4: Avoiding Inconsistent Circuits in the ANSYS Low-Frequency Electromagnetic Analysis Guide. Also, your model cannot intermix CIRCU94 elements with other circuit elements (CIRCU124 and CIRCU125). Their finite element formulations are not compatible (see Section 12.2: Element Compatibility in the ANSYS Low-Frequency Electromagnetic Analysis Guide).

You can directly connect an electrical circuit to a piezoelectric finite element model through a set of common nodes (Figure 8.9: “Electrical Circuit Connections”) or by coupling separate nodes. The location of the circuit with respect to the distributed piezoelectric domain is arbitrary and does not affect the analysis results.

**Figure 8.9 Electrical Circuit Connections**

The piezoelectric-circuit analysis can be either full transient or harmonic. You follow standard procedures to define analysis options and to apply loads. Refer to Section 7.3: Piezoelectric Analysis for recommendations and restrictions that apply to piezoelectric analysis. You can activate geometric nonlinearities to account for large deflections of the piezoelectric domain.

You apply loads to a circuit in any of the following ways:

- Specify voltage at a node using the D command and the VOLT label.
- Specify negative charge at a node using the F command (AMPS label).
- Include a CIRCU94 independent current source in your model.
- Include a CIRCU94 independent voltage source in your model.

For the independent current and voltage source options, you use KEYOPT(2) to specify the type of excitation and the corresponding real constants to specify the load function. For transient analyses, you can also use real constants to set the initial current in inductors or the initial voltage in capacitors.

Table 8.1: “Piezoelectric Circuit Element Output Data” summarizes the output data for CIRCU94. For more information on nodal and element solutions, see Solution Output in the ANSYS Elements Reference.

**Table 8.1 Piezoelectric Circuit Element Output Data**

<table>
<thead>
<tr>
<th>Data Type</th>
<th>Solution Output</th>
</tr>
</thead>
<tbody>
<tr>
<td>Primary Data</td>
<td>• Nodal voltages (VOLT) for each component</td>
</tr>
<tr>
<td></td>
<td>• Negative charge (CURR) at the “passive” node for a voltage source option</td>
</tr>
</tbody>
</table>
8.4. Sample Electromechanical-Circuit Analysis

In this example, you will perform an electromechanical-circuit analysis of a MEMS structure.

8.4.1. Problem Description

This is an analysis of a micro-mechanical system composed of an electrostatic transducer coupled to a mechanical resonator as shown in Figure 8.10: “Electrostatic Transducer - Resonator Model”. A discrete spring, mass, and damper represent the mechanical resonator. A discrete electromechanical transducer represents the parallel plate capacitor. The electrostatic transducer has a series of pulse excitation voltages applied as shown in Figure 8.11: “Excitation Voltages”. Our goal is to compute the time-transient displacement of the mechanical resonator (at Node 2).

Figure 8.10 Electrostatic Transducer - Resonator Model
The problem can be easily built in the Circuit Simulator using the electromechanical transducer element (TRANS126), the mass element (MASS21), and the combination element (COMBIN14). The problem uses the µMKSV system of units. For a parallel plate capacitor, the capacitance varies as a function of the gap. The real constant C0 represents the capacitance relationship.

Four load steps simulate two pulse excitations on the transducer. You can apply the voltage to the transducer either directly at the node (D command), or through the use of the general circuit element (CIRCU124). A large-signal nonlinear transient solution is run using auto time-stepping (AUTOTS). The resulting displacements are plotted using POST26.

The following are the input parameters:

- Plate area = $1 \times 10^8$ (µm)$^2$
- Initial gap = 150 µm
- Relative permittivity = 1.0
- Mass = $1 \times 10^{-4}$ Kg
- Spring Constant = 200 µN/µm
- Damping Coefficient = $40 \times 10^{-3}$ µNs/µm

The excitation at node 2 is:

<table>
<thead>
<tr>
<th>Time (sec)</th>
<th>Value (Volts)</th>
</tr>
</thead>
<tbody>
<tr>
<td>0.00</td>
<td>5.0</td>
</tr>
<tr>
<td>0.03</td>
<td>0.0</td>
</tr>
<tr>
<td>0.06</td>
<td>10.0</td>
</tr>
<tr>
<td>0.09</td>
<td>0.0</td>
</tr>
<tr>
<td>0.12</td>
<td>0.0</td>
</tr>
</tbody>
</table>
8.4.2. Results

Figure 8.12: “Mechanical Resonator Displacement (at Node 2)” shows the resulting displacement.

Figure 8.12 Mechanical Resonator Displacement (at Node 2)

8.4.3. Command Listing

The command listing below demonstrates the problem input (captured and edited from the Circuit Builder). Text prefaced by an exclamation point (!) is a comment.

```plaintext
/batch,list
/show,file
/prep7
/title, Transient response of an electrostatic transducer-resonator
/com, µMKSV units

et,1,trans126 ! EM Transducer Element
r,1,,1,150 ! gap=150 µN
rmore,8.854e-6*1e8 ! C0 term (eps*area)
n,1
n,2,0.1
e,1,2

et,2,21,,4 ! Mass element (UX,UY dof option)
r,2,1e-4 ! Mass
rmod,2,7,,1
type,2
real,2
e,2

et,3,14,,1 ! Spring
keyopt,3,7,1 ! This is an undocumented keyopt used to suppress!
               ! a warning message about noncoincident nodes.
               ! It does not alter the performance of the element.
               ! It is not intended for general use.

r,3,200,,,05,1 ! k=200 µN/ µm, graphical offsets
```

ANSYS Coupled-Field Analysis Guide. ANSYS Release 10.0. © SAS IP, Inc.
8.5. Sample Piezoelectric-Circuit Analysis (Batch or Command Method)

This example problem considers a circuit-fed piezoelectric transducer. CIRCU94 elements are used to model the electrical components and SOLID226 elements are used to model of the piezoelectric transducer.

8.5.1. Problem Description

This is an analysis of a Lead Zirconate Titanate (PZT-4) piezoelectric transducer connected in parallel with a resistor (R) and excited by a current source (I) as shown in Figure 8.13: “Piezoelectric Circuit”. First perform a transient analysis to determine the current through the resistor. Then perform a harmonic analysis near the third resonance mode to determine the voltage drop across the resistor.

```
! Damper
keyopt,4,7,1 ! This is an undocumented keyopt used to suppress
! a warning message about noncoincident nodes.
! It does not alter the performance of the element.
! It is not intended for general use.

r,4,,40e-3,-.05,1 ! Damping coeff=40e-3 μMs/μm, graphical offsets

nsel,s,node,,1,3,2 ! Fix transducer and ground
nsel,all

nsel,all

! Fix voltage ground

nsel,all

! Fix UY motion for mass

/dolu

! Transient analysis - large signal
antyp,trans

! Step boundary conditions
kbc,1
d,2,volt,5 ! Apply 5 volts to transducer
time,.03 ! Time at end of first load step
deltim,.0005,.0001,.01 ! Set initial, minimum and maximum time incr.
autos,on ! Use auto time-stepping
cnttol,f ! Convergence on force

time,.06 ! Repeat for addition load steps

solve
d,2,volt,0

time,.09
d,2,volt,10
	solve
time,.12
	d,2,volt,0
	solve

finish

/post26

nsol,2,2,u,x ! Retrieve displacement

/xrange,0,.12

/yrange,-.02,.01

/axlab,x,Time (sec.)

/axlab,y,Displacement (micro meters)

plvar,2 ! Plot displacement

finish
```
To verify results, perform analyses using equivalent electric circuits. To further verify the transient results, use the following analytical solution derived using the Laplace transformation technique:

$$I = 1 - \exp\left(-\frac{t}{R}\right)$$

### 8.5.2. Problem Specifications

PZT-4 has the following material properties:

- Density = 7700 kg/m$^3$
- Permittivity at constant strain:
  - Relative permittivity in X direction = 729
  - Relative permittivity in Y direction = 635
  - Relative permittivity in Z direction = 729

**Piezoelectric Matrix $[e]$ C/m$^2$:**

$$
\begin{bmatrix}
0 & -5.2 & 0 \\
0 & 15.1 & 0 \\
0 & -5.2 & 0 \\
0 & 0 & 0 \\
12.7 & 0 & 0 \\
0 & 0 & 12.7 \\
0 & 0 & 0 \\
0 & 0 & 0
\end{bmatrix}
$$

**Stiffness matrix $[c]$ x 10$^{-10}$ N/m$^2$:**

$$
\begin{bmatrix}
13.9 & 7.43 & 7.78 & 0 & 0 & 0 \\
11.5 & 7.43 & 0 & 0 & 0 & 0 \\
13.9 & 0 & 0 & 0 & 0 & 0 \\
2.56 & 0 & 0 & 0 & 0 & 0 \\
2.56 & 0 & 0 & 0 & 0 & 0 \\
3.06 & 0 & 0 & 0 & 0 & 0
\end{bmatrix}
$$
The piezoelectric transducer is a block with a side length of 1 mm.

The current is a 1.3 mA step load for the transient analysis.

\section*{8.5.3. Equivalent Electric Circuits (Reduced Order Model)}

\subsection*{Transient Analysis}

For the transient analysis, approximate the piezoelectric transducer with a capacitor as shown in Figure 8.14: “Equivalent Circuit - Transient Analysis”. The equivalent static capacitance $C_s$ is determined from a static analysis of the piezoelectric region. The resistance $R$ and analysis time are adjusted to:

\begin{align*}
R & = 1e-4/C_s \\
t & = 2R(C_s)
\end{align*}

\begin{figure}[h]
\centering
\includegraphics[width=0.5\textwidth]{equivalent_circuit_transient_analysis.png}
\caption{Equivalent Circuit - Transient Analysis}
\end{figure}

\subsection*{Harmonic Analysis}

In a harmonic analysis performed near the $i$th resonance mode, approximate the piezoelectric transducer with capacitors and inductors ($C_s$, $C_i$, and $L_i$) as shown in Figure 8.15: “Equivalent Circuit - Harmonic Analysis at $i$th Piezoelectric Resonance”. Determine the equivalent dynamic capacitance $C_i$ and dynamic inductance $L_i$ from a modal analysis of the piezoelectric region and the following equations:

\begin{align*}
C_i & = (Q_i)^2/\Omega_i^2 \\
L_i & = 1/((\Omega_i)^2(C_i))
\end{align*}

where:

$Q_i = \text{Electrode charge of } i\text{th piezoelectric resonance}$

$\Omega_i = \text{Angular frequency of } i\text{th piezoelectric resonance}$
To more accurately represent the piezoelectric transducer, include more capacitor-inductor branches in the reduced order model. For example, use nine capacitor-inductor branches as shown in Figure 8.16: “Equivalent Circuit - Harmonic Analysis Near the 3rd Piezoelectric Resonance”. The nine \( C_i - L_i \) (i = 1, 2, ... 9) branches correspond to the first nine resonance modes of the piezoelectric transducer. The equivalent static capacitance and resistance are adjusted to:

\[
\begin{align*}
C_0 &= C_s - \text{SUM of } C_i \ (i = 1 \text{ through } 9) \\
R &= 0.9/(\Omega_3)(C_0)
\end{align*}
\]

where:

\( \Omega_3 \) = Angular frequency of the third resonance mode

\[\text{Figure 8.16 Equivalent Circuit - Harmonic Analysis Near the 3rd Piezoelectric Resonance}\]

### 8.5.4. Results

**Transient Analysis**

Transient analyses results are shown in Table 8.2: “Transient Analysis Results”.

<table>
<thead>
<tr>
<th>Time (ms)</th>
<th>I (mA)</th>
<th>Piezoelectric-Circuit</th>
<th>Equivalent (Reduced Model)</th>
<th>Analytical (Target)</th>
</tr>
</thead>
<tbody>
<tr>
<td>0.00400</td>
<td>0.0389</td>
<td>0.0385</td>
<td>0.0392</td>
<td></td>
</tr>
<tr>
<td>0.03200</td>
<td>0.2736</td>
<td>0.2733</td>
<td>0.2739</td>
<td></td>
</tr>
</tbody>
</table>
Harmonic analysis results are shown in Figure 8.17: “Harmonic Analysis Results”. The curves for the piezoelectric-circuit analysis and the reduced order model are identical because nine modes have been taken into account.

**Figure 8.17  Harmonic Analysis Results**

![Graph showing harmonic analysis results]

### 8.5.5. Command Listing

The command listing below demonstrates the problem input (captured and edited from the Circuit Builder). Text prefaced by an exclamation point (!) is a comment. An alternative element type and material input are included in the comment lines.

```
/batch,list
/prep7
/title,Transient and harmonic analyses of a piezoelectric circuit
```
! Set up the model for the piezoelectric element
!
! Material properties for PZT-4
!
mp,DENS,1,7700               ! Density, kg/m**3

! Relative permittivity at constant strain
!
tb,DPER,1

tbdata,1,729,635,729
!
! - Alternative input of permittivity if used with SOLID5
!
mp,PERX,1,729
mp,PERY,1,635
mp,PERZ,1,729
!
tb,ANEL,1
!
! Anisotropic elastic stiffness, N/m^2
!
tbdata,1,13.9E10,7.43E10,7.78E10 ! c11,c13,c12

tbdata,7,11.5E10,7.43E10 ! c33,c13

tbdata,12,13.9E10 ! c11

tbdata,16,2.56E10 ! c44

tbdata,19,2.56E10 ! c44

tbdata,21,3.06E10 ! c66

! Piezoelectric stress coefficients, C/m^2
!
tb,PIEZ,1

tbdata,2,-5.2 ! e31

tbdata,5,15.1 ! e33

tbdata,8,-5.2 ! e31

tbdata,10,12.7 ! e15

tbdata,15,12.7 ! e15
!
! Define a piezoelectric cube (H = 1 mm)
!
H = 1e-3               ! Transducer size, m

! Define volume
block,0,H,0,H,0,H
!
! Define the number of element divisions
!
et,1,SOLID226,1001 ! 3-D coupled-field brick, piezo option
esize,2 ! Define the number of element divisions
!
et,1,SOLID5,3 ! lower order 3-D coupled-field brick, piezo option
!
mat,1 type,1 ! Set element attributes
!
umstr,node,14 ! Set starting node number for the solid model
!
vmesh,1 ! Generate nodes and elements
!
*get,Epz,elem,,count ! Get the number of solid elements
!
! Apply boundary conditions and loads to the piezoelectric transducer
!
nsel,s,loc,z,0 ! Define bottom electrode

cp,1,volt,all
*get,n_bot,node,0,num,min ! Get master node on bottom electrode

nsel,s,loc,z,H ! Define top electrode

cp,2,volt,all
*get,n_top,node,0,num,min ! Get master node on top electrode

nsel,s,loc,z,0 ! Impose displacement constraints

d,all,uz,0

nsel,r,loc,y,0
d,all,uy,0

nsel,r,loc,x,0
d,all,ux,0

nsel,all
d,n_bot,volt,0 ! Ground bottom electrode

d,n_top,volt,1 ! Apply unit voltage to top electrode

fini
!
! Determine static capacitance of the piezo-cube
!
/solu
antype,static ! Static analysis
solve ! Get electric charge on top electrode
! *get,Cs,node,n_top,rf,chrg ! use AMPS label with SOLID5
Cs = abs(Cs) ! C = Q/V, where V = 1 Volt

/com, Equivalent parameters of the piezoelement
/*com,
/คอม, Static capacitance Cs = %Cs% F
fini
!
! Determine equivalent dynamic electric parameters of the piezo-cube
! /solu
antype,modal ! Modal analysis
nmodes = 9 ! Number of modes
modopt,LANB,nmodes ! Block Lanczos solver
mxpand,nmodes,,yes ! Calculate element results and reaction forces
d,n_top,volt,0 ! Short-circuit top electrode
solve ! Solve for resonance frequency
fini
/post1
*dim,C,array,nmodes ! Define arrays to store equivalent parameters
*dim,L,array,nmodes
PI2 = 2*3.14159
Co = Cs
set,first
/คอม,
*do,i,1,nmodes
*get,Fi,mode,i,freq ! Get frequency
*get,Qi,node,n_top,rf,chrg ! Get electric charge on top electrode
! *get,Qi,node,n_top,rf,amps ! Use AMPS label with SOLID5
Omi = PI2*Fi ! Convert linear frequency to angular
C(i) = (Qi/Omi)**2 ! Calculate equivalent dynamic capacitance
Co = Co - C(i) ! Adjust static capacitance for dynamic terms
L(i) = 1/(Omi**2*C(i)) ! Calculate equivalent dynamic inductance
*if,i,eq,3,then ! Get third mode frequency for harmonic analysis
F3 = Fi $ Om3 = Omi
*endif
/คอม, Mode %i%
/คอม, Resonant frequency F = %Fi% Hz
/คอม, Dynamic capacitance C = %C(i)% F
/คอม, Dynamic inductance L = %L(i)% H
/คอม,
set,next
*enddo
/คอม, Adjusted static capacitance Co = %Co% F
fini
/คอม,---------------------------------------------------------------
/คอม,---------------------------------------------------------------
/คอม, Transient analysis of the piezoelectric and equivalent circuits
/คอม,---------------------------------------------------------------
!
! Set up equivalent circuit for transient analysis (Fig. 2)
!
/prep7
!
! Element types
!
et,2,CIRCU94,0 ! Resistor option
et,3,CIRCU94,2 ! Capacitor option
et,4,CIRCU94,3 ! Independent current source (step) option
!
! Real constants
!
RC = 1.e-4 ! RC constant
Imax = 1.e-3 ! Current level
r,1, RC/Cs ! Resistance, Ohm
r,2, Cs ! Equivalent static capacitance, F
r,3, Imax ! Current
!
! Nodes and elements
!
node,1,0,0
node,2,0,1
node,3 $ real, 1
node,4,1,0
node,5,2,0,1
node,6,2,1
node,7,3,0,1
node,8,3,1
node,9,4,0
node,10,4,1
node,11,5,0
node,12,5,1
node,13,6,0
node,14,6,1
node,15,7,0
node,16,7,1
node,17,8,0
node,18,8,1
node,19,9,0
node,20,9,1
node,21,10,0
node,22,10,1
node,23,11,0
node,24,11,1
node,25,12,0
node,26,12,1
e, 2, 1 ! Resistor connected to lumped capacitor (elem Epz+1)
e, n_top, n_bot ! Resistor connected to piezoelement (elem Epz+2)
type,3 $ real, 2
*/
Section 8.5: Sample Piezoelectric-Circuit Analysis (Batch or Command Method)

```
e, 2, 1                  ! Capacitor Cs (elem Epz+3)
type,4 $ real, 3

! Current source feeding RC(lumped)-circuit
e, 1, 2

! Current source feeding RC(piezo)-circuit
e, n_bot, n_top

fini
/solu
ddele,n_top,volt        ! Delete voltage constraints on top electrode
dl,volt,0
antype,trans           ! Transient analysis
nsubs,50
time,2*RC              ! Analysis time, s
tintp,0.25,0.5,0.5      ! Set time integration parameters piezo analysis
kbc,1                   ! Stepped load
outres,esol,all         ! Transient analysis
solve
fini
/post26
esol,2,Epz+1,,smisc,2,I_equiv  ! Store output current
esol,3,Epz+2,,smisc,2,I_piezo
store
    ! Calculate analytical solution
exp,4,1,,,,,-1/RC          ! exp(-t/RC)
filldata,5,,,,,1
add,6,5,4,I_targ,Imax,Imax I_targ = Imax*(1 - exp(-t/RC))
nprint,7
prvar,I_piezo,I_equiv,I_targ ! Print and plot output current
plvar,I_piezo,I_equiv,I_targ
fini
/com, Harmonic analysis of the piezoelectric and equivalent circuits
/com, near the third mode of vibration
/com, ...........................................................................
!
! Set up equivalent circuit for harmonic analysis (Fig. 4)
! - adjust static capacitance (replace Cs with Co)
! - add dynamic Li-Ci branches
!
/prep7
! Modify RC constant
rmodif,1,1, RC/Co
emodif,Epz+1
emodif,Epz+2
! of piezo-circuit resistor
antype,trans
et,5,CIRCU94,1
rl1 = 2  $  rl2 = 3      ! Initialize real constant numbers
r,rl1, L(i)              ! Dynamic inductance for mode i, H
r,rl2, C(i)              ! Dynamic capacitance for mode i, F
n,nd, i,0.5              ! Connection node between Li and Ci
type,5 $ real,rl1
e, 2, nd
! Inductor Li
type,3 $ real,rl2
e, nd, 1
*endo
di
/com, Harmonic analysis
harfrq,0.95*F3,1.1*F3
nsubs,100
solve
fini
/post26
esol,4,Epz+2,,smisc,1,V_piezo  ! Store output voltage
esol,3,Epz+1,,smisc,1,V_equiv
store
prcplx,1                 ! Output amplitude and phase
```
nprint,9
prvar,V_piezo,V_equiv  ! Print and plot output voltage
/axlab,x,Frequency (Hz)
/axlab,y,|Vout| (volts)
plvar,V_piezo,V_equiv
fini
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